

Next generation semiconductor devices and applications

(차세대 반도체 소자 및 응용)

장소: 공과대학 6호관 510호

시간: 화 (6-A, 6-B, 7-A, 7-B, 8-A, 8-B)

5. Next generation electronic devices

Organic Non-volatile Memory

Organic Resistive Switching Memory
(Simple & Advanced Architecture)

Memory and Logic Will Play a Critical Role in Future Printed Electronics Applications

Smart tagging of
“everything”



**Memory and
logic enable
integrated
systems**

(e.g., store max/min temperature, turn
power on/off etc.)

Large area displays,
disposable price displays
and lighting



Disposable sensors/tags



Organic Non-volatile Memory Devices (resistive change type)

Organic memory refers to devices that are used **to store data or programs on a temporary or permanent basis using organic materials as an active layer.**

Usage of organic memory devices

“Deposited on top of flexible plastic materials, plastic circuitry could, for instance, be built into flexible displays and packed into smaller spaces inside cellphones, MP3players, plastic RFID tags and even credit cards.”



“The time for OMDs might finally be at hand ... even if the first application is the humble **radio-frequency identification (RFID) tags** used in retail store product.”

From “TechNewsWorld 2011”

Merits

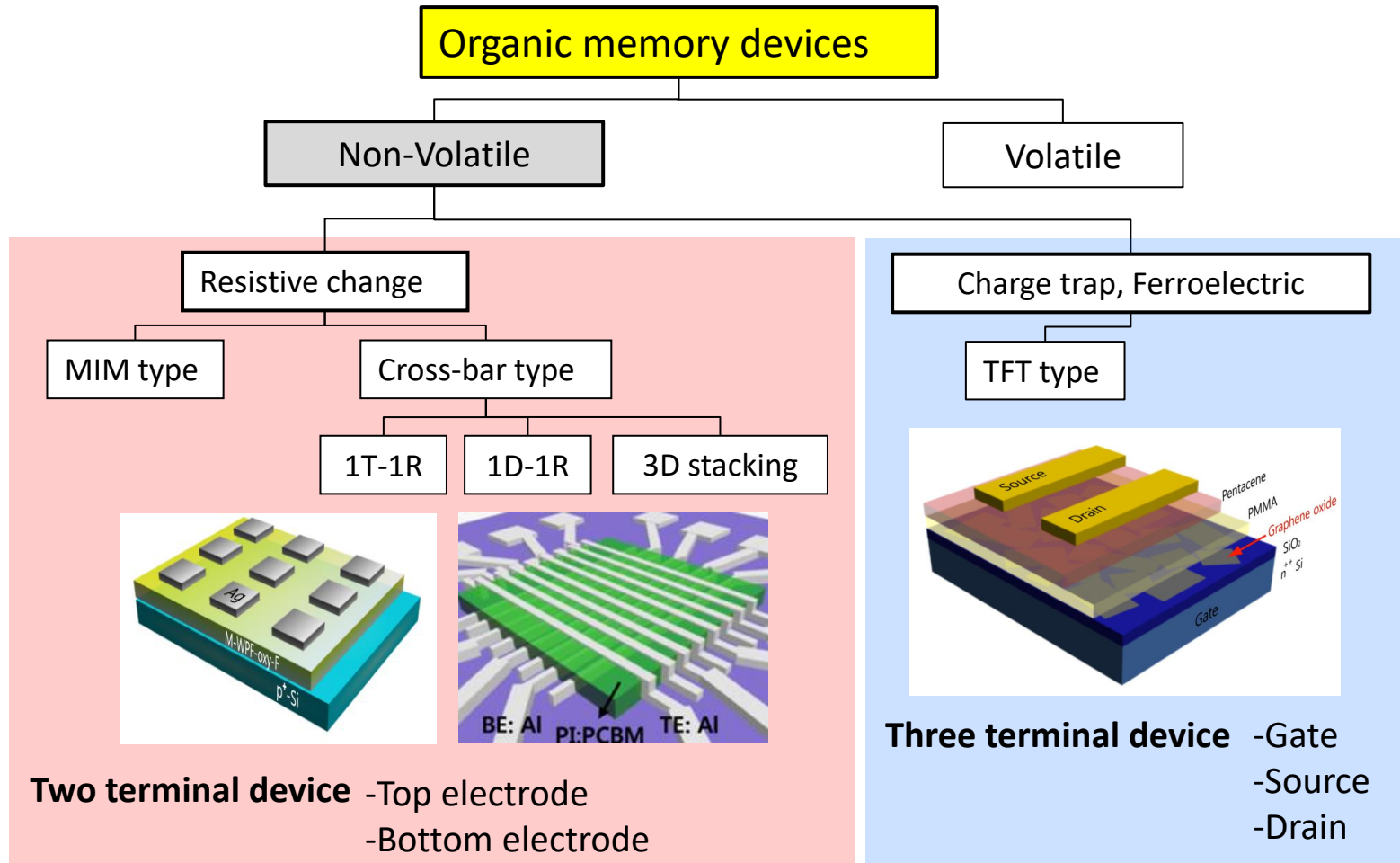
- Simple structure
- Easy of fabrication
- Compatibility with flexible substrates
- Comparative low cost
- Multilayer stacking

Challenges

- Unknown switching mechanism
- Unstable in ambient condition
- Data retention time
- Reliability
- **Processability** → **UV patterning & cross-linking**
- **Integration** → **Cross-bar structure**
- **Novel architecture** → **1D-1R or 1T-1R architecture**

Family Tree of Organic Non-volatile Memory

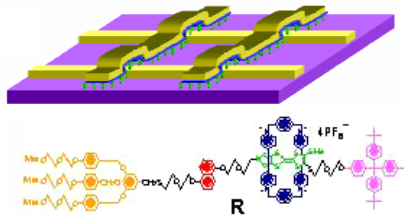
Organic Non-volatile Memory



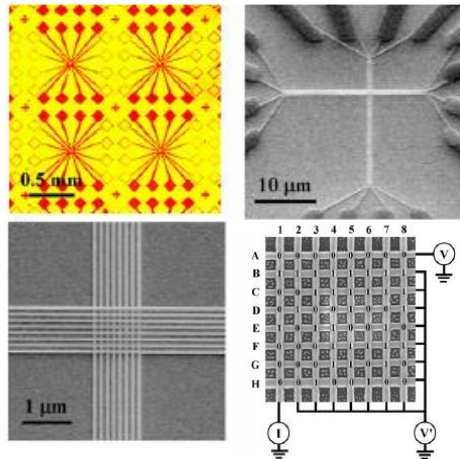
Types of Organic Non-volatile Memory

Resistive change type

Molecular Memory

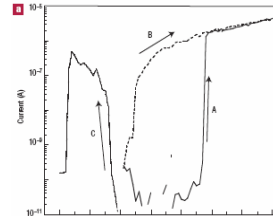
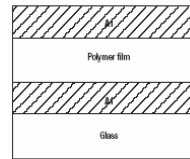


- Rotaxane molecular film
- Layer thickness ~ 2 nm 6.4 Gbit/cm²

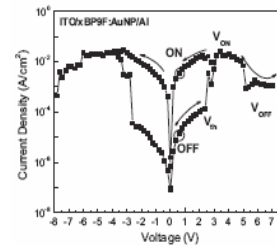


Chen *et al*, *Nanotechnology* 14, 462 (2003)

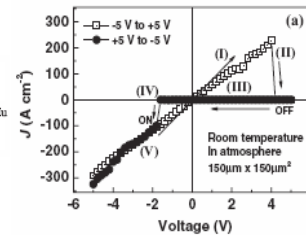
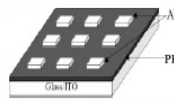
Polymer Memory



Ouyang *et al*, *Nat. Mater.* 3, 918 (2004)



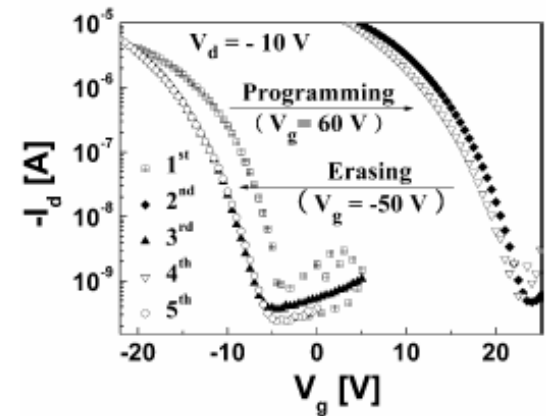
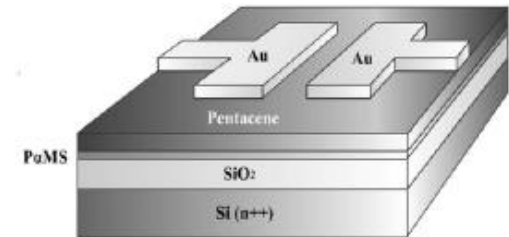
Bozano *et al*, *Adv. Func. Mater.* 15, 1933 (2005)



Ling *et al*, *Adv. Mater.*, 17, 455 (2005)

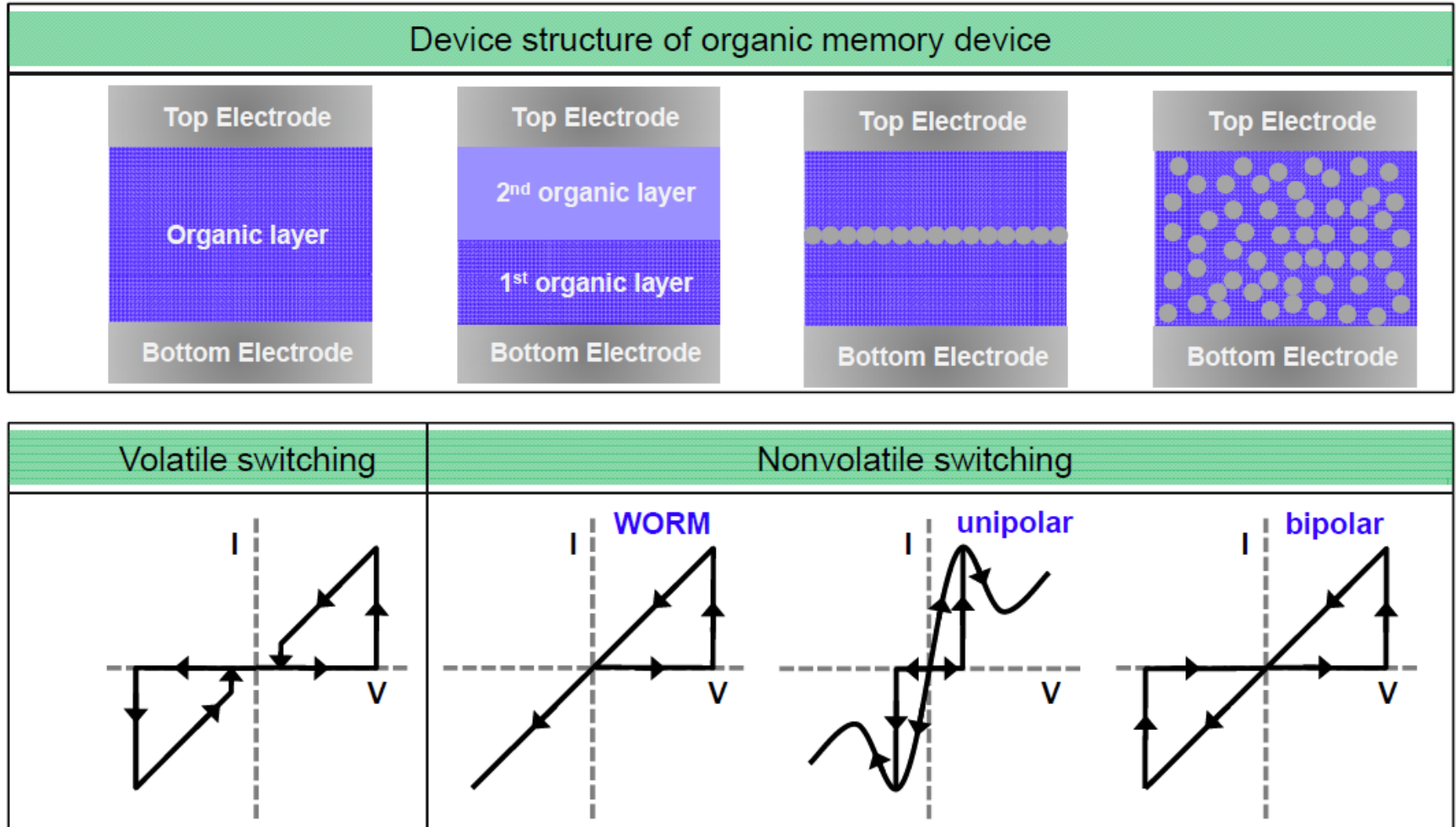
Flash type

charge trap memory



Beag *et al*, *Adv. Mater.* 18, 3179 (2006)

Organic memory devices



Materials for Organic Non-volatile Memory

- Organic materials for resistive change memory devices

Small molecule

Switching type	Structure
1. Hysteresis, without threshold or NDR	ITO / NiPc:PAH / Al
2. Reverse polarity switching, no NDR	Au / anthracene-co-PMMA / Al ITO / DDQ, TAPA, Fluorescein, Eosin Y or Rose Bengal : PAH / Al
3. Threshold, but volatile	Al / tetracene / Au Ag / anthracene / Ag Al / pentacene / Al
4. WORM	ITO, Au, or Al / Alq ₃ / Al
5. Switching by either polarity, NDR	ITO or Au / Alq ₃ or NPB / Al, Ag or Au Al / AIDCN / Ag

Donor-acceptor complexes

Switching type	Structure
2. Reverse polarity switching, no NDR	Cu / CuTCNQ / Al ITO / EuVB-co-PVK / Al ITO / PEDOT:PSS / RE-complex:PVK / LiF / Ca / Ag HOPG / NBMN:pDA / STM Al / CuTCNQ / Al Al / TTF:PCBM:PS HOPG / CDHAB / STM-W Cu / CuTCNQ / Cu ITO / P3HT:CNT / Al Cu / CuTCNQ / Al
3 or 4 Volatile or WORM depending on conditions	
4. WORM	Ag / DC:BDGP / Ag ITO / EuVB-co-PF / Al

Mobile-ion, electrochemical system

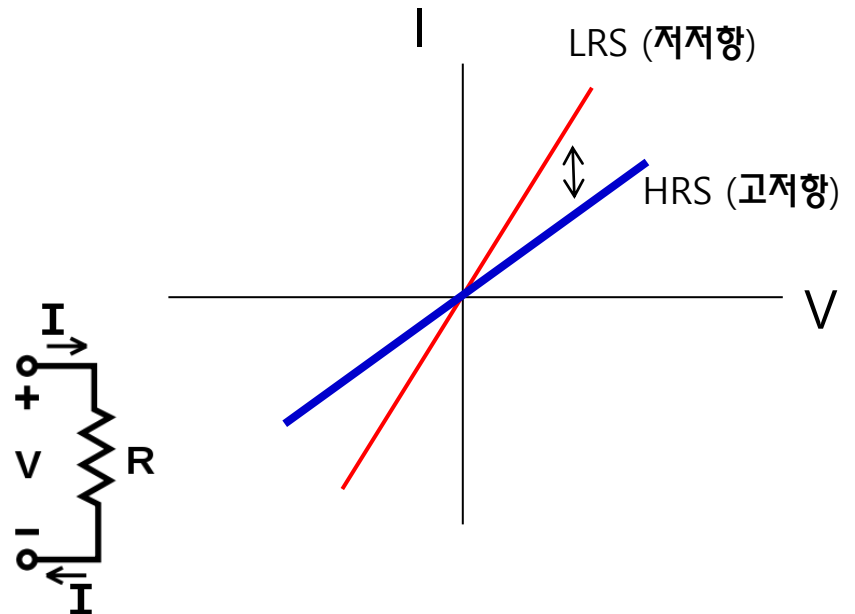
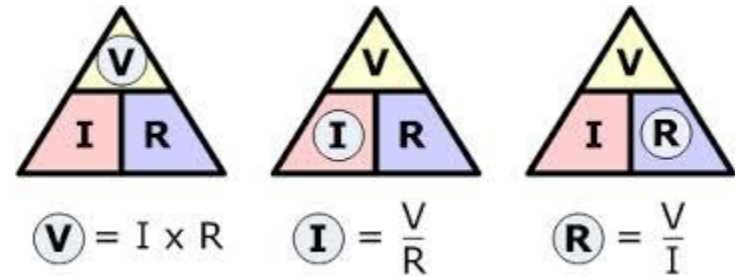
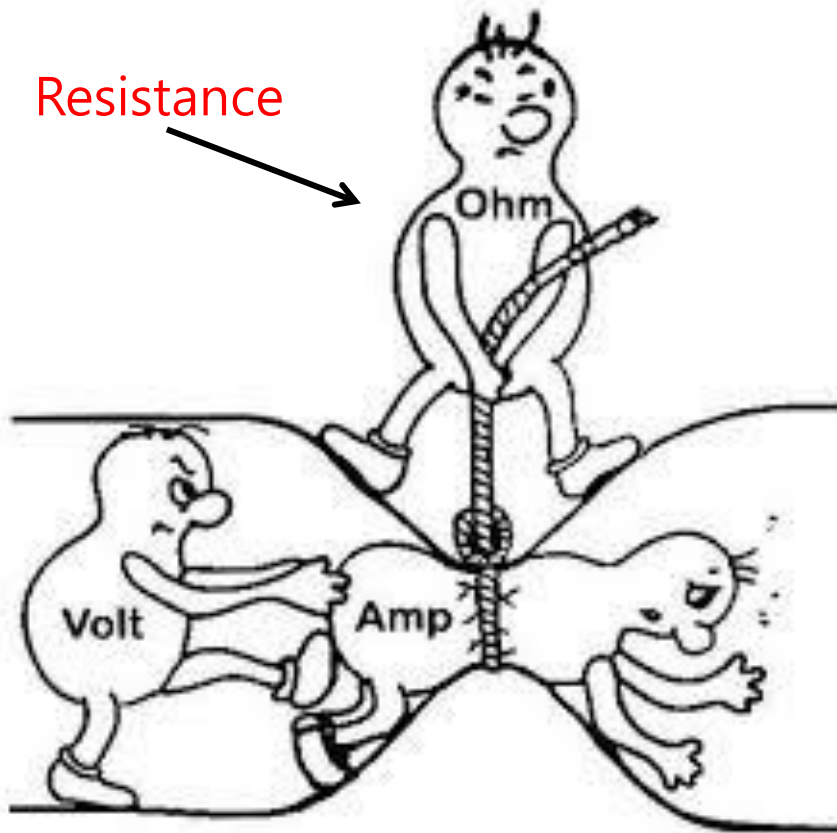
Switching type	Structure
1. Hysteresis, without threshold or NDR	PEDOT:PSS:NaCl / 6T-co-PEO / Al
2. Reverse polarity switching, no NDR	Pt / MEHPPV / RbAg ₅ I ₄ / Ag ? / PPhA:NaCl / ?

Nanoparticle blends

Switching type	Structure
1. Hysteresis, without threshold or NDR	Al / (Au-2NT or BET):PS / Al
2. Reverse polarity switching, no NDR	Al / AIDCN / (Al) / AIDCN / Al Al / (Au-DT):8HQ, or DMA:PS / Al Al / (Au):PTFE / Au
3. Threshold, but volatile	Pt / (Ag):gd-HMDS or gd-benzene / Pt Al / AIDCN / (Al):AIDCN / AIDCN / Al Ag / CNPF / (Ag) / CNPF / Ag ? / TDCN / (Ag) / TDCN / ?
4. WORM	Al / Alq ₃ / (Al) / Alq ₃ / Al
5. Switching by either polarity, NDR	ITO / (Au-TPP):xBP9F / Al ITO / (Au-TPP):xHTPA / Ca / Al ITO / (Au-TPP):xHTPA / Al ITO / (Au-TPP):xHTPA / xHTPA / Al Al / NPB / (Al) / NPB / Al Cr / Alq ₃ / (Al) / Alq ₃ / Al Cu / Alq ₃ / (Al) / Alq ₃ / Al ITO / Alq ₃ / (Al) / Alq ₃ / Al Au / Alq ₃ / (Al) / Alq ₃ / Al Ni / Alq ₃ / (Al) / Alq ₃ / Al Al / Alq ₃ / (Mg) / Alq ₃ / Al Al / Alq ₃ / (Ag) / Alq ₃ / Al Al / Alq ₃ / (Cr) / Alq ₃ / Al Al / Alq ₃ / (CuPc) / Alq ₃ / Al Al / (Au-DT):P3HT / Al

Working Principle of Organic Non-volatile Memory

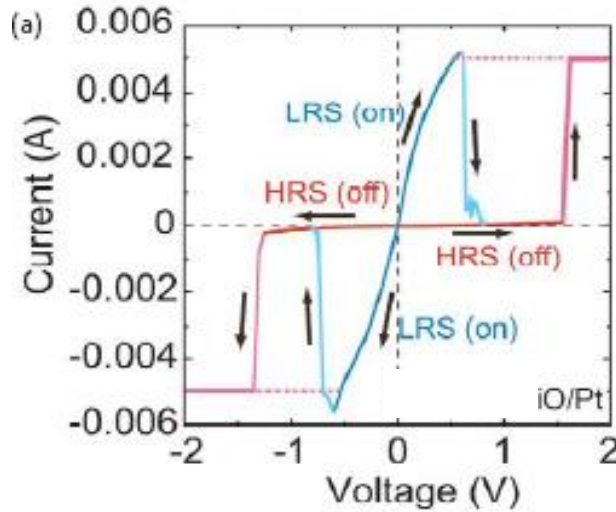
Ohm's Law



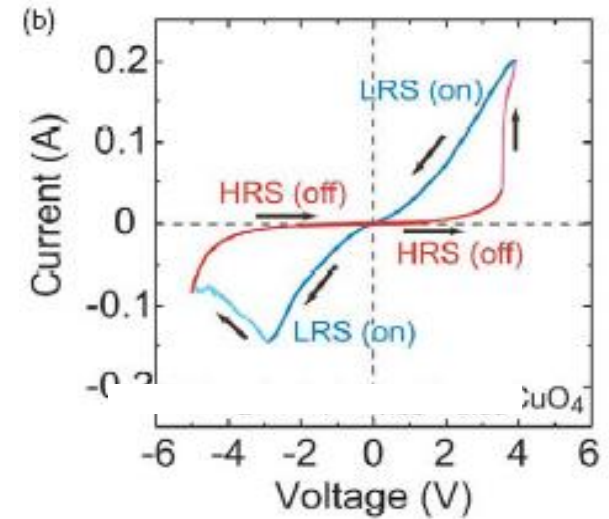
Working Principle of Organic Non-volatile Memory

- Switching type of organic memory device

- **Unipolar switching**



- **Bipolar switching**

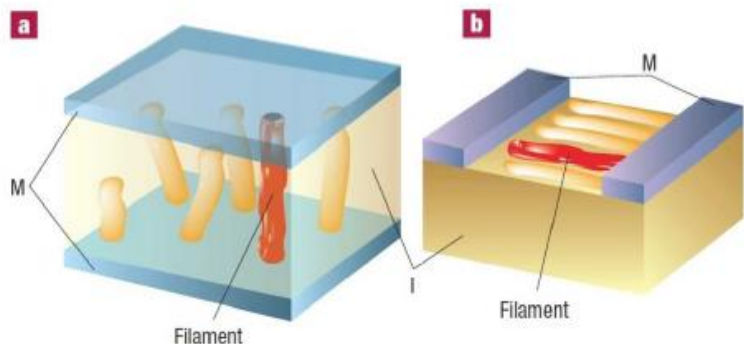


- Switching parameters

- Kind of materials
- Thickness of organic active layer
- Kind of metal electrodes
- Device architecture
- How to Measure-compliance current, sweep voltage, sweep direction

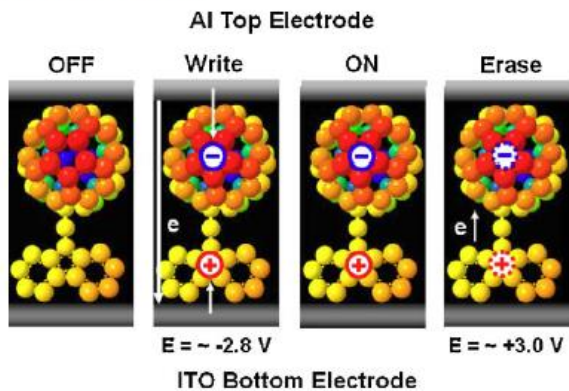
Mechanisms of Organic Non-volatile Memory

✓ Filamentary conduction



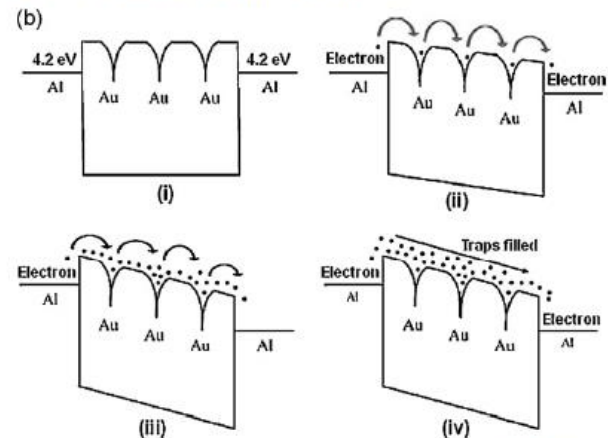
Nat. Mater. 6, 833 (2007)

✓ Charge-transfer



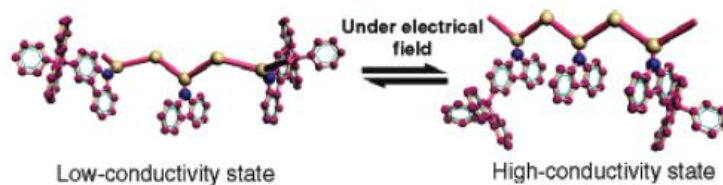
Langmuir, 23, 312 (2007)

✓ Space charge and traps



IEDL, 28, 569 (2007)

✓ Conformational Change



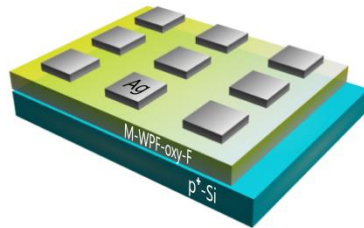
J. AM. CHEM. SOC. 130, 2120 (2008)

✓ Ionic conduction, tunneling effect, and etc

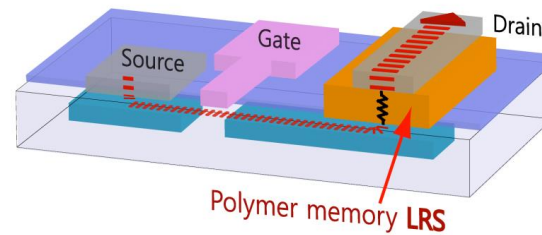
Research Summary of Organic Non-volatile Memory

- Simple Architecture
 - >>> MIM, Cross-bar
- Advanced Architectures for organic memory device
 - >>> 1T-1R, 1D-1R, 3D stacking, Flexible memory

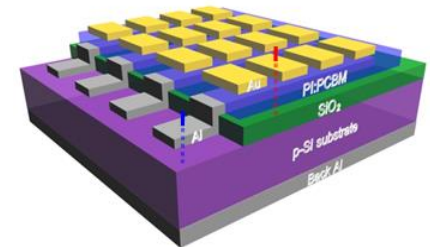
MIM



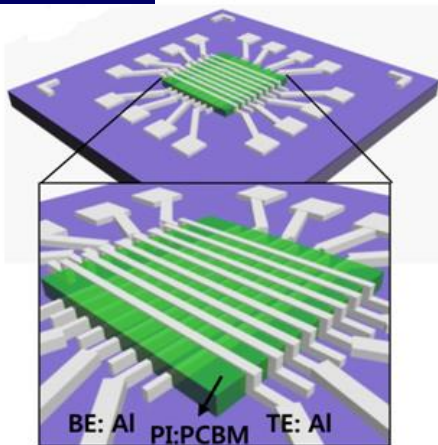
1T-1R



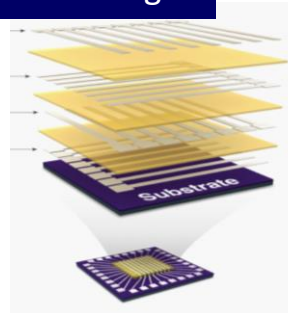
1D-1R



Cross bar



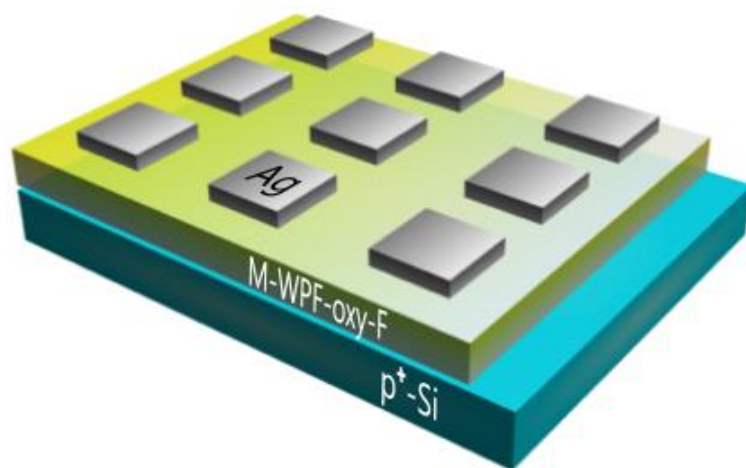
3D stacking



Flexible memory



Simple Architecture for Organic Non-volatile Memory

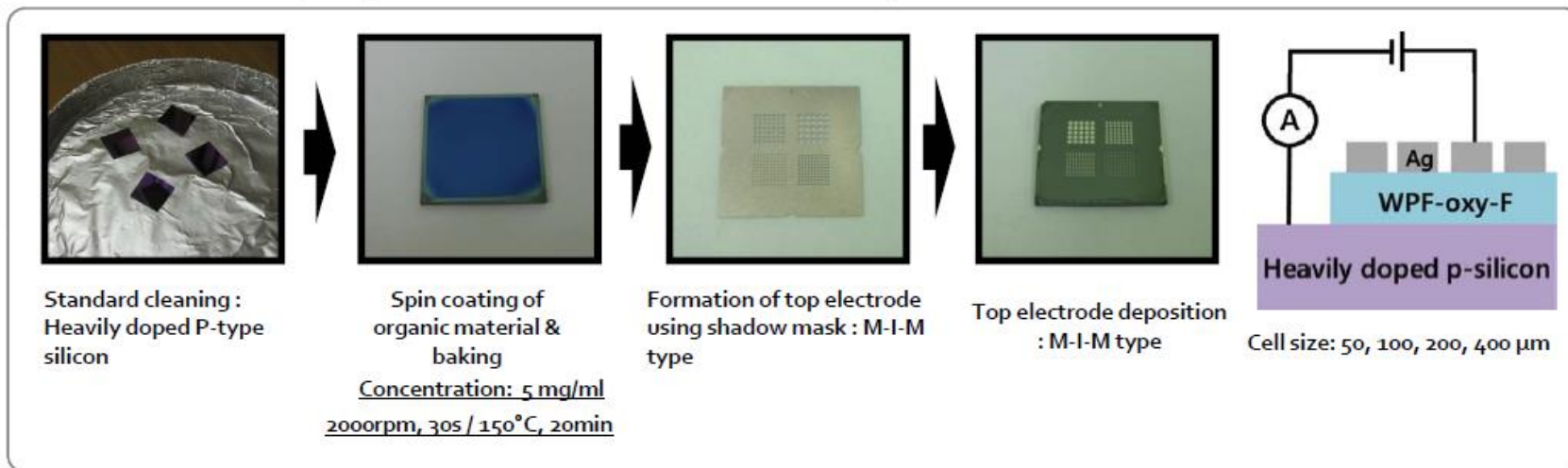


- Kim *et al.* Applied Physics Letters 92, 253308 (2008)
Kim *et al.* IEEE Electron Device Letters 29, 852 (2008)
Kim *et al.* Nanotechnology 20, 025201 (2009)
Kim *et al.* Organic Electronics 10, 496 (2009)
Kim *et al.* Organic Electronics, 11, 109 (2010)
Cha *et al.* Materials Science and Engineering B, 191 (2015)
Cha *et al.* ACS Applied Materials & Interfaces, 9, 2730 (2017)

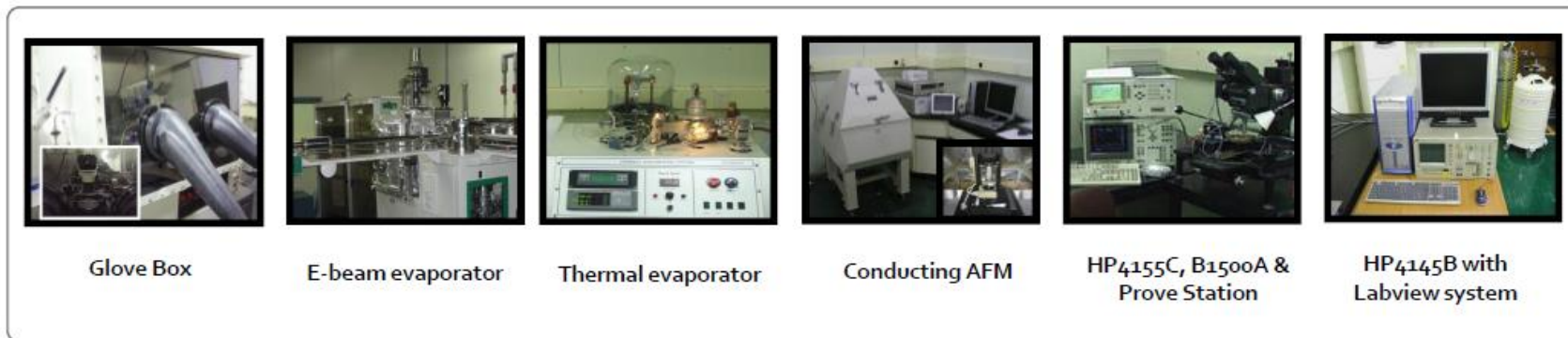
Simple Architecture for Organic Non-volatile Memory

M-I-M Unit-cell Type Single Layer Organic Memory Devices

Fabrication of polymer non-volatile memory device

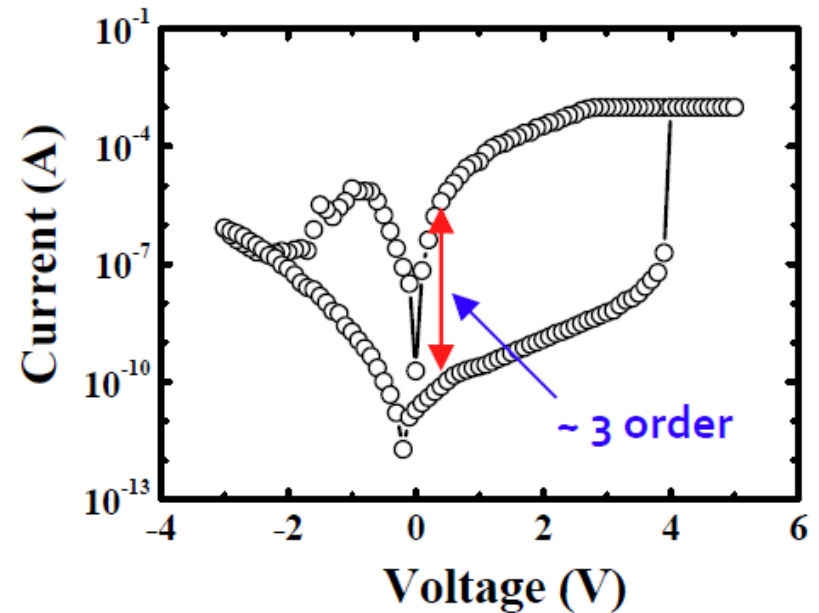
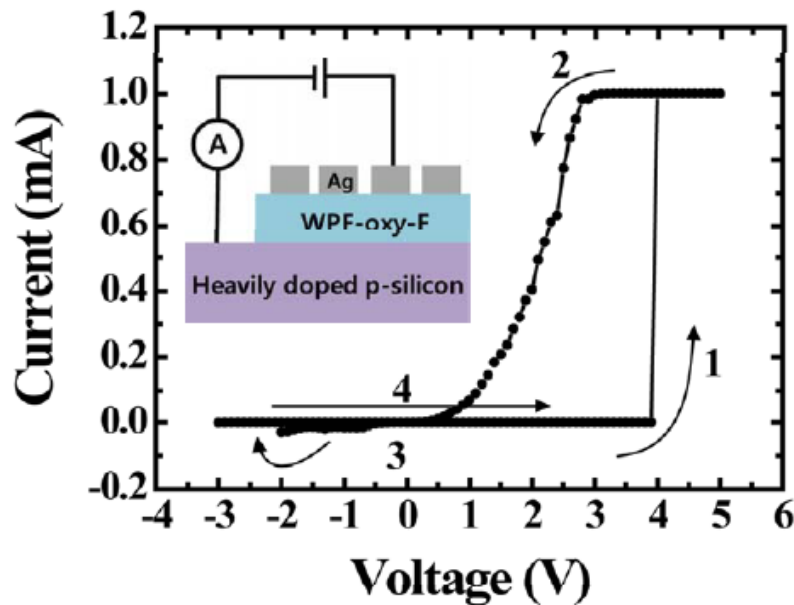


Equipment for fabrication and analysis



Simple Architecture for Organic Non-volatile Memory

Switching behavior of WPF-oxy-F memory devices



- WPF-oxy-F memory device showed **bipolar switching** behavior
- More than **3 orders** of magnitude of on/off ratio
- Low operation voltage (-3V ~ 5V)

Kim et al, *Appl. Phys. Lett.* 92, 253308 (2008)

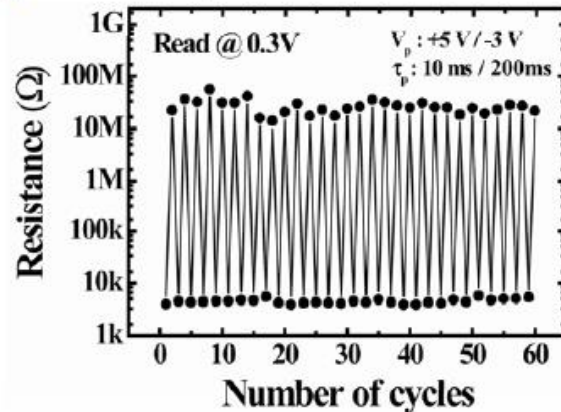
Kim et al, *IEEE Electron. Device Lett.* 29, 852 (2008)

I. Simple architecture for organic memory device

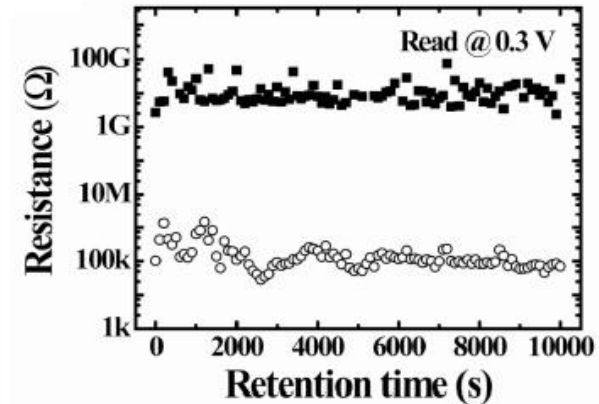
Micron-scale MIM / Submicron-scale MIM

Specific memory performances

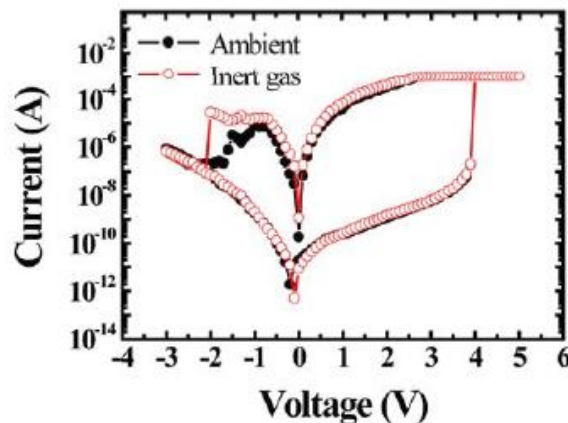
Cycling (pulsed I-V)



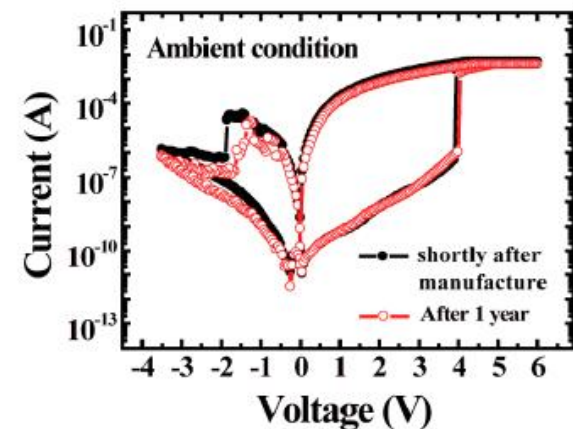
Retention characteristics



Ambient, inert environment



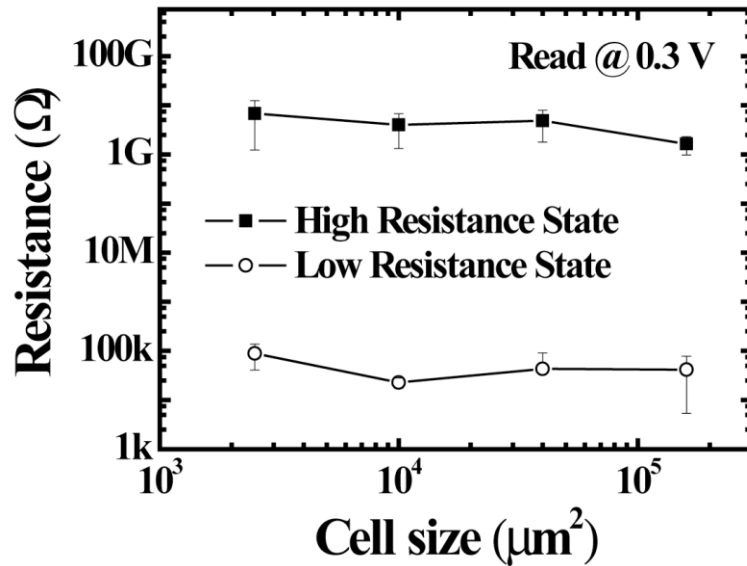
Stability



Simple Architecture for Organic Non-volatile Memory

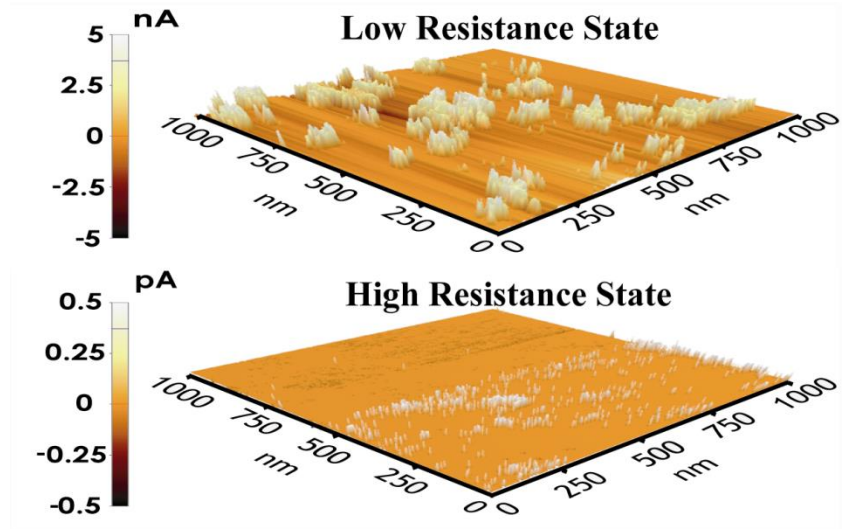
Memory Mechanism

Cell area dependence



- From ~120 devices for 50, 100, 200, 400 μm cell sizes
- Resistance of LRS did not change over cell size
- Resistance of HRS slightly decreased

Conducting-AFM images

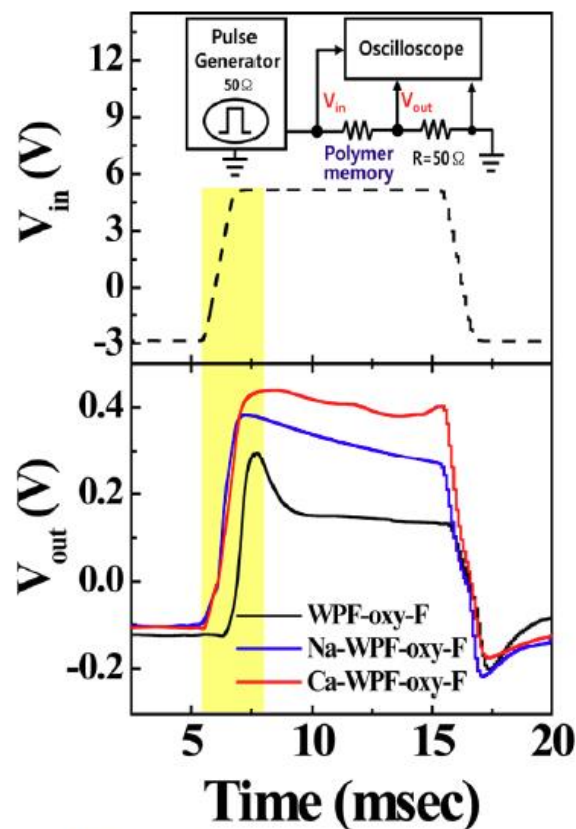
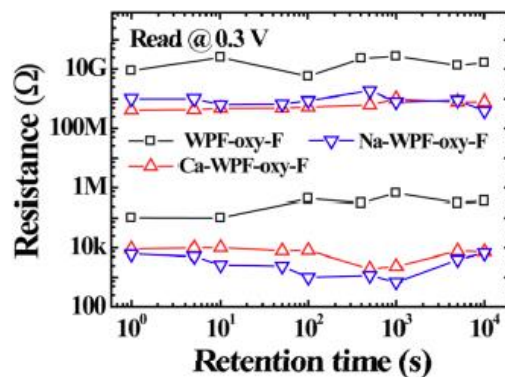
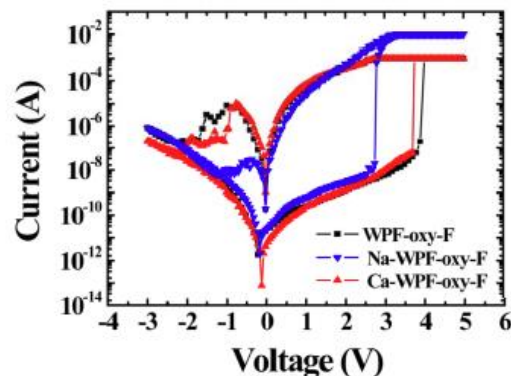
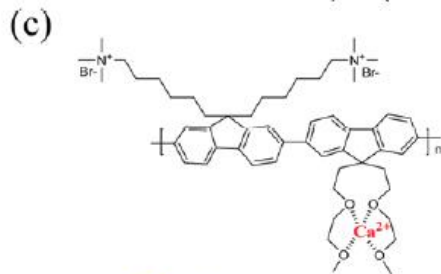
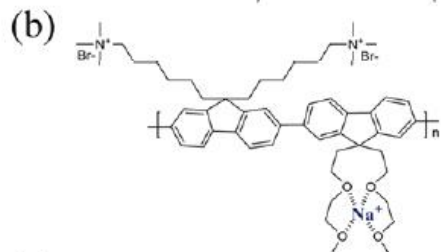
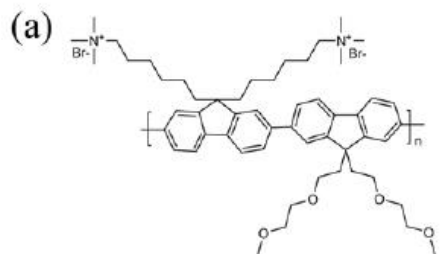


There are localized and distributed conduction paths in current image of LRS

Programming : 6.5V tip bias
Erasing : -3.0V tip bias
Reading : 1.0V tip bias

Simple Architecture for Organic Non-volatile Memory

Switching (Response) Time



- **Response time** when switching from HRS to LRS:

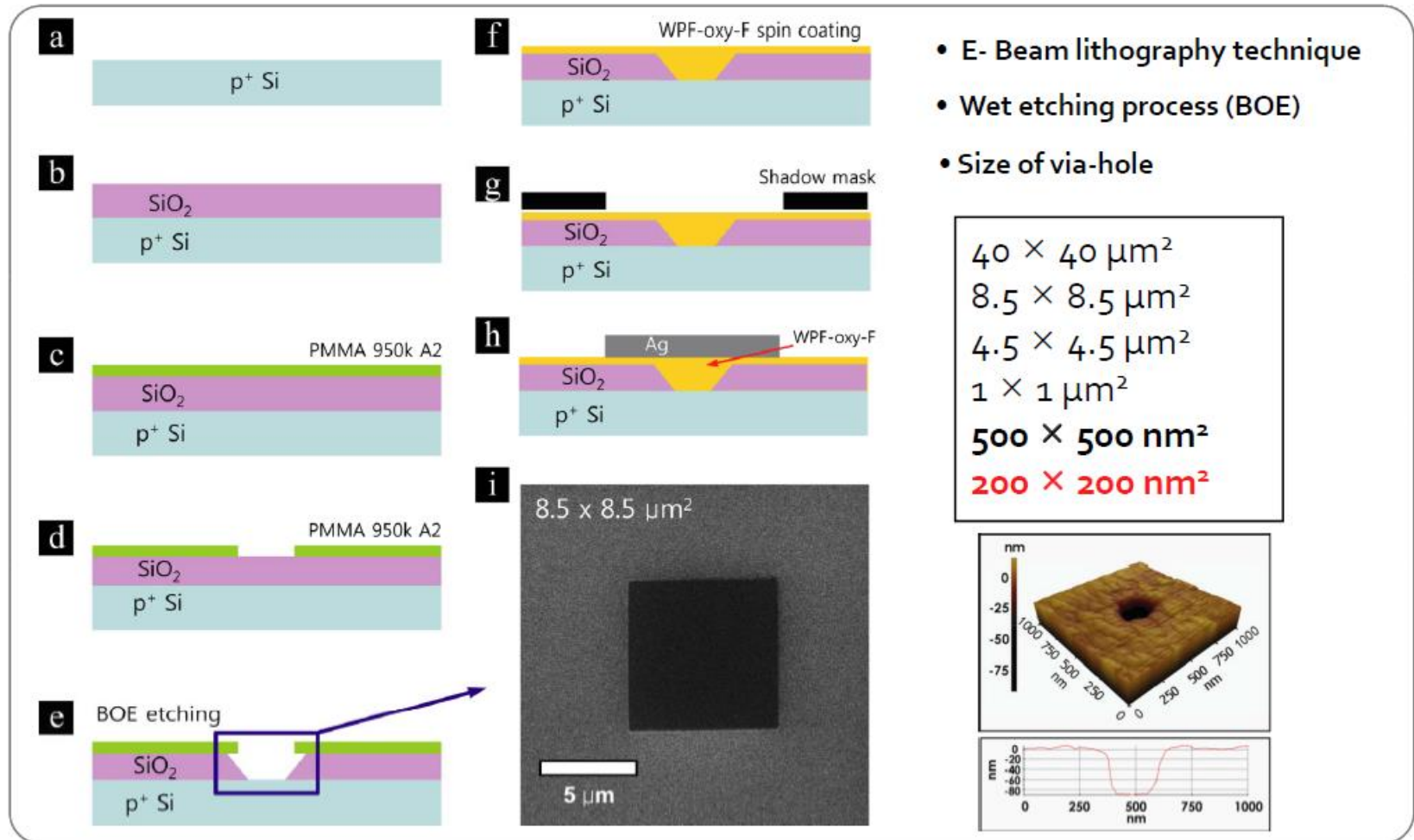
Na-WPF-oxy-F and Ca-WPF-oxy-F: ~10 μs

WPF-oxy-F: ~2 ms

Kim et al. Organic Elect. 10, 496 (2009)

Sub-micron scale Organic Non-volatile Memory

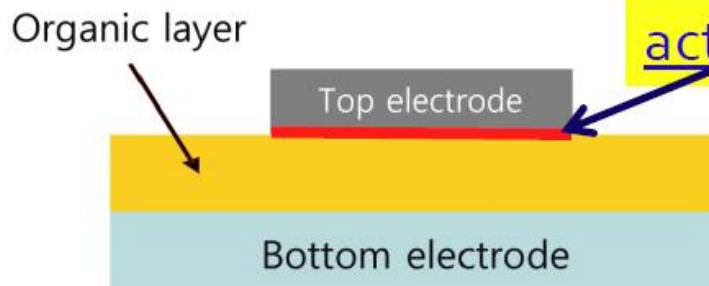
Nanoscale (Sub-micron scale) M-I-M Unit-cell Devices



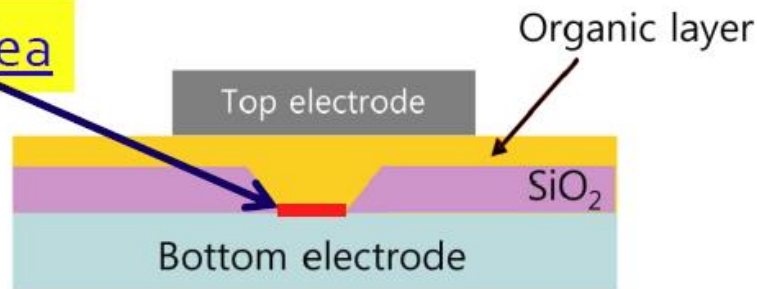
Sub-micron scale Organic Non-volatile Memory

What is the difference between *conventional M-I-M* between *scalable via-hole*?

- Conventional MIM



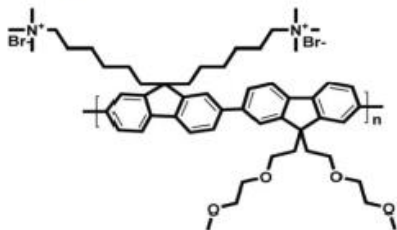
- Scalable via-hole



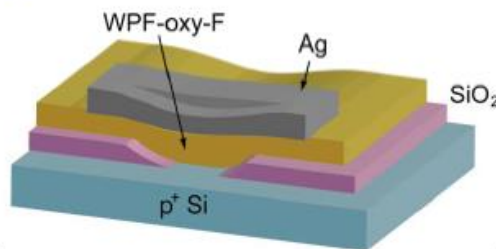
The main difference is how to define active area.

In this study

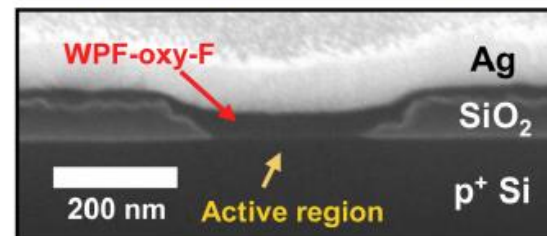
- Organic material



- 3D schematics



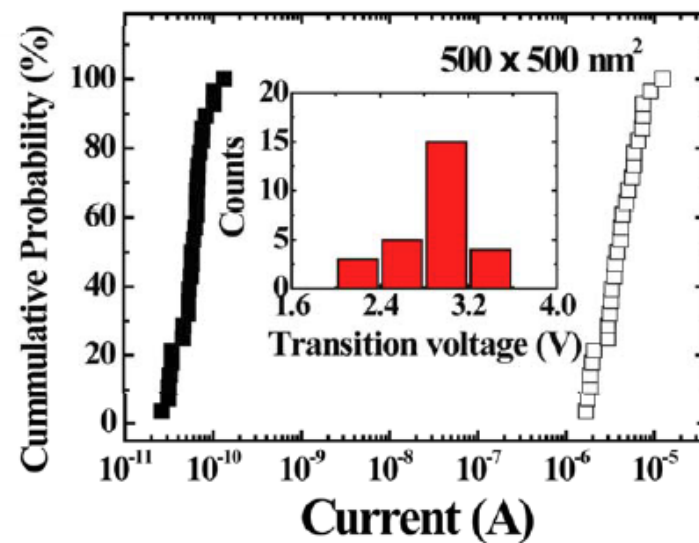
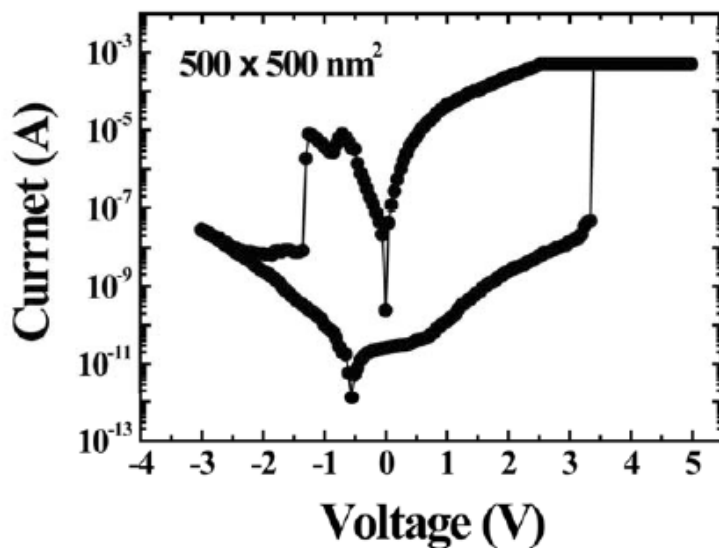
- SEM image of organic memory device



Sub-micron scale Organic Non-volatile Memory

Nanoscale (Sub-micron scale) switching characteristics

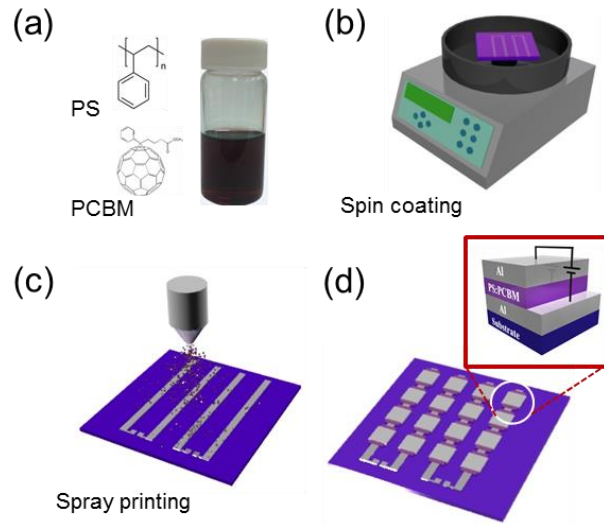
Switching behavior of sub-micron scale polymer memory device



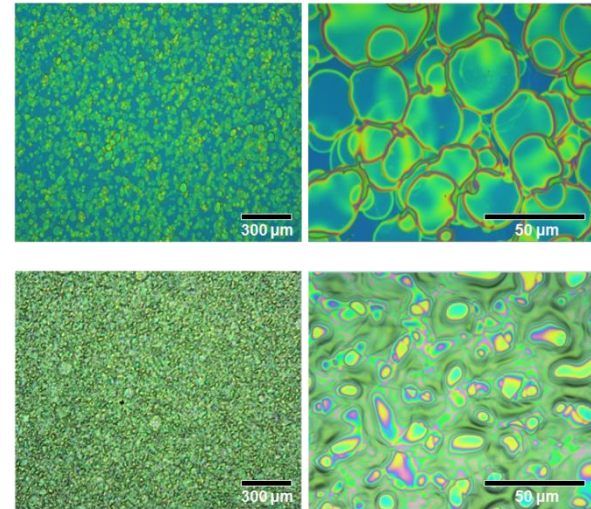
- Excellent electrical bistability with a high ON/OFF ratio ($I_{\text{ON}}/I_{\text{OFF}} \sim 10^4$ at 0.3 V)
- Excellent device-to-device switching uniformity
- Narrow distribution of transition voltage (2.8V ~ 3.2 V)

Organic Non-volatile Memory by **Printing Process**

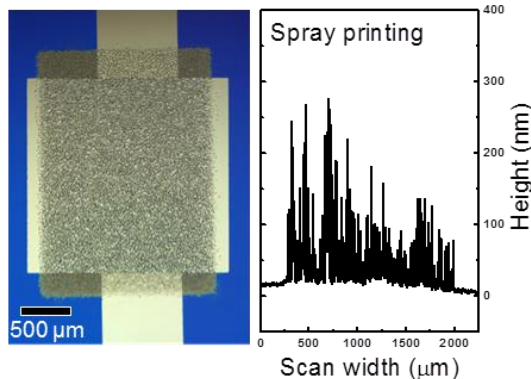
- Organic memory devices via. spray printing method



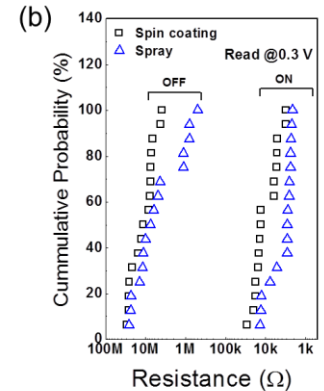
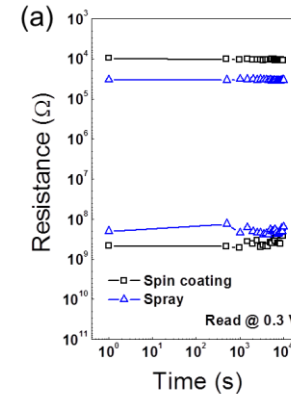
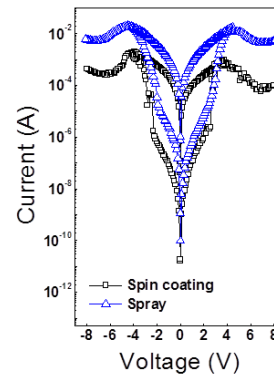
Optical images of sprayed film



Optical image

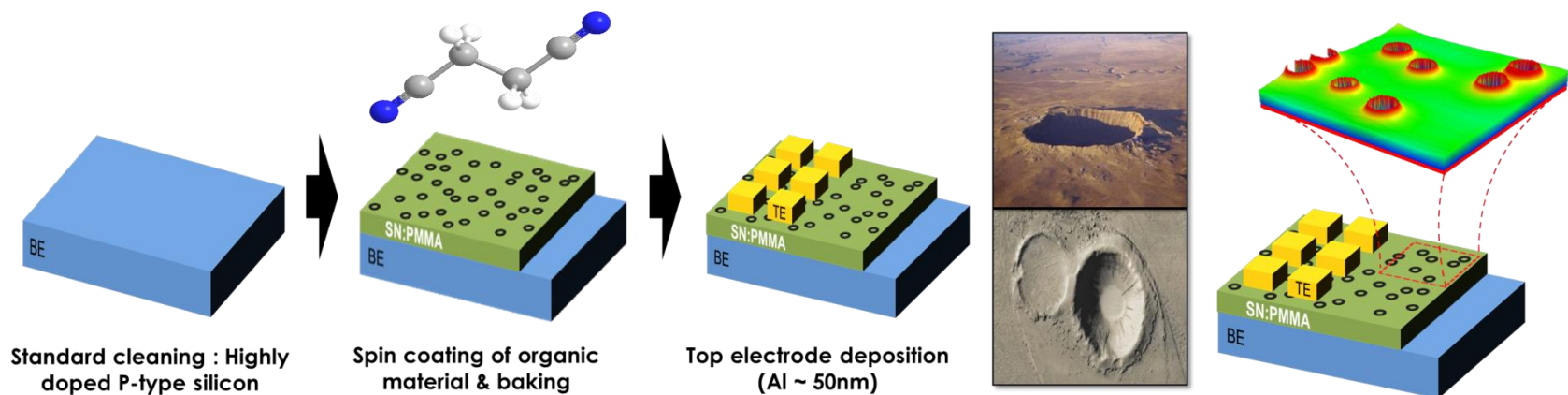


Electrical properties



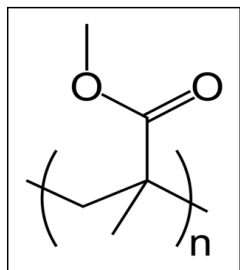
Self-assembled Organic Composite Non-volatile Memory

- Micro-crater from succinonitrile-poly(methyl methacrylate) organic composite



► Active layer (PMMA:SN) is polystyrene in chlorobenzene Spin casting was performed under 2000rpm for 40sec.

Poly(methyl methacrylate)



- Density 1.18 g/cm³
- Electrical conductivity (s) 10–19 S/m
- Thermal conductivity (k) 0.19 W/(m K)
- Melting point 160 °C
- Specific heat (c) 1.4 kJ/(kg K)
- **Poly(methyl methacrylate) (PMMA)** is a transparent thermoplastic often used in sheet form as a lightweight or shatter-resistant alternative to soda-lime glass.
- The same material can be utilised as a casting resin; in inks and coatings, and also has other uses.

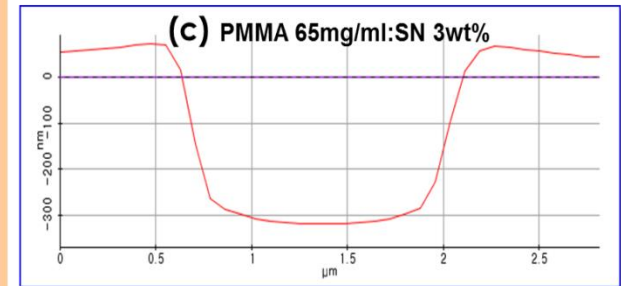
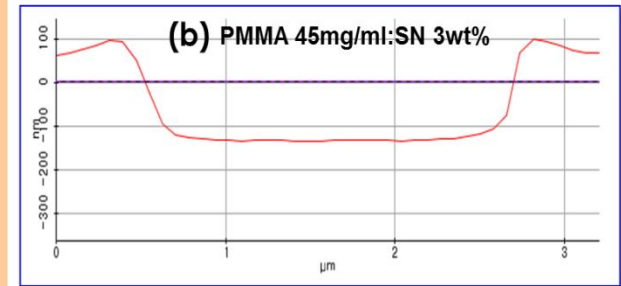
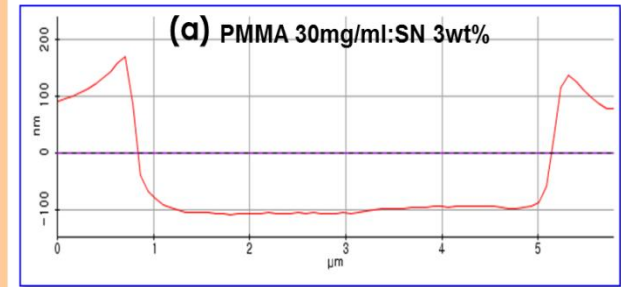
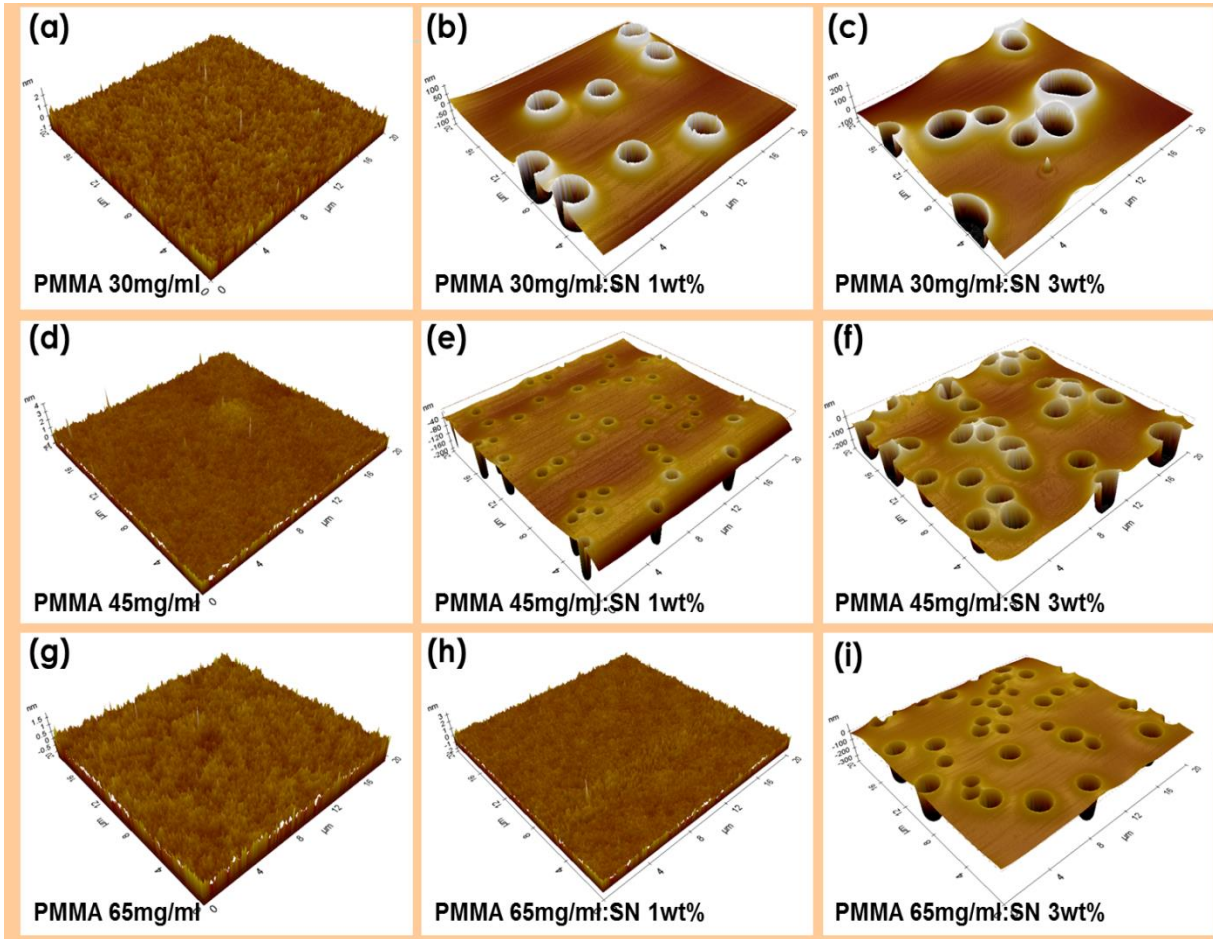
Succinonitrile



- Density 985 mg mL⁻¹
- Melting point 52 °C
- Specific heat (c) 145.60 J K⁻¹ mol⁻¹
- **Succinonitrile**, also butanedinitrile, is a nitrile, with the formula of C₂H₄(CN)₂. It is a colorless solid that melts at 57 °C, hence its waxy consistency.

Self-assembled Organic Composite Non-volatile Memory

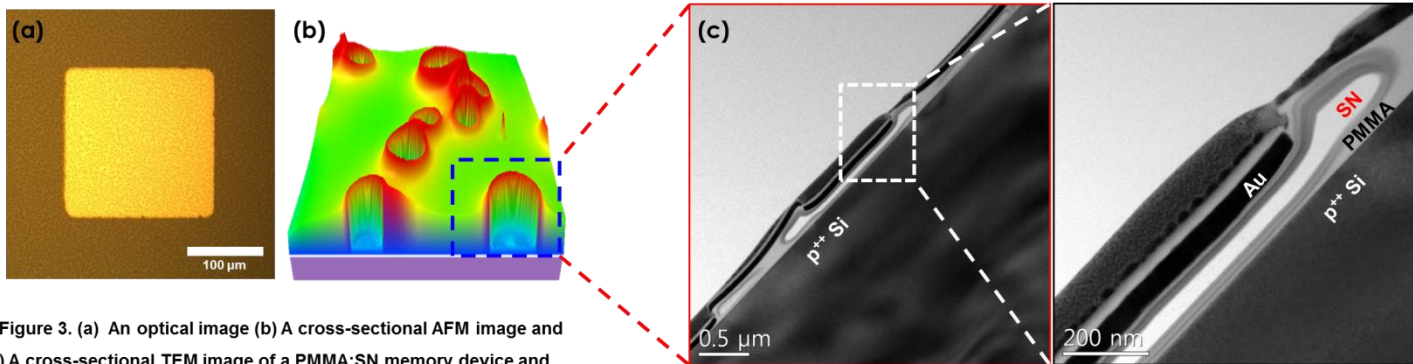
- AFM images of PMMA:SN composite film



Self-assembled Organic Composite Non-volatile Memory

- TEM, EDX, XPS analysis on PMMA:SN composite film

- Optical microscopy images of organic non-volatile memory device with spin-coating process



• Figure 3. (a) An optical image (b) A cross-sectional AFM image and (c) A cross-sectional TEM image of a PMMA:SN memory device and HRTEM image an PMMA:SN film memory device.

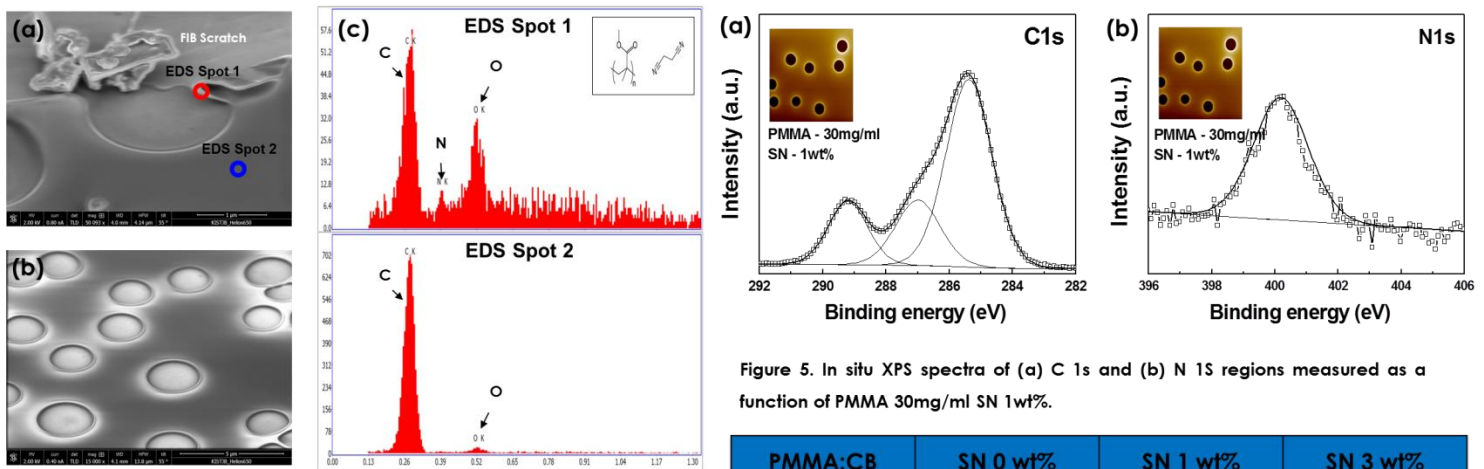
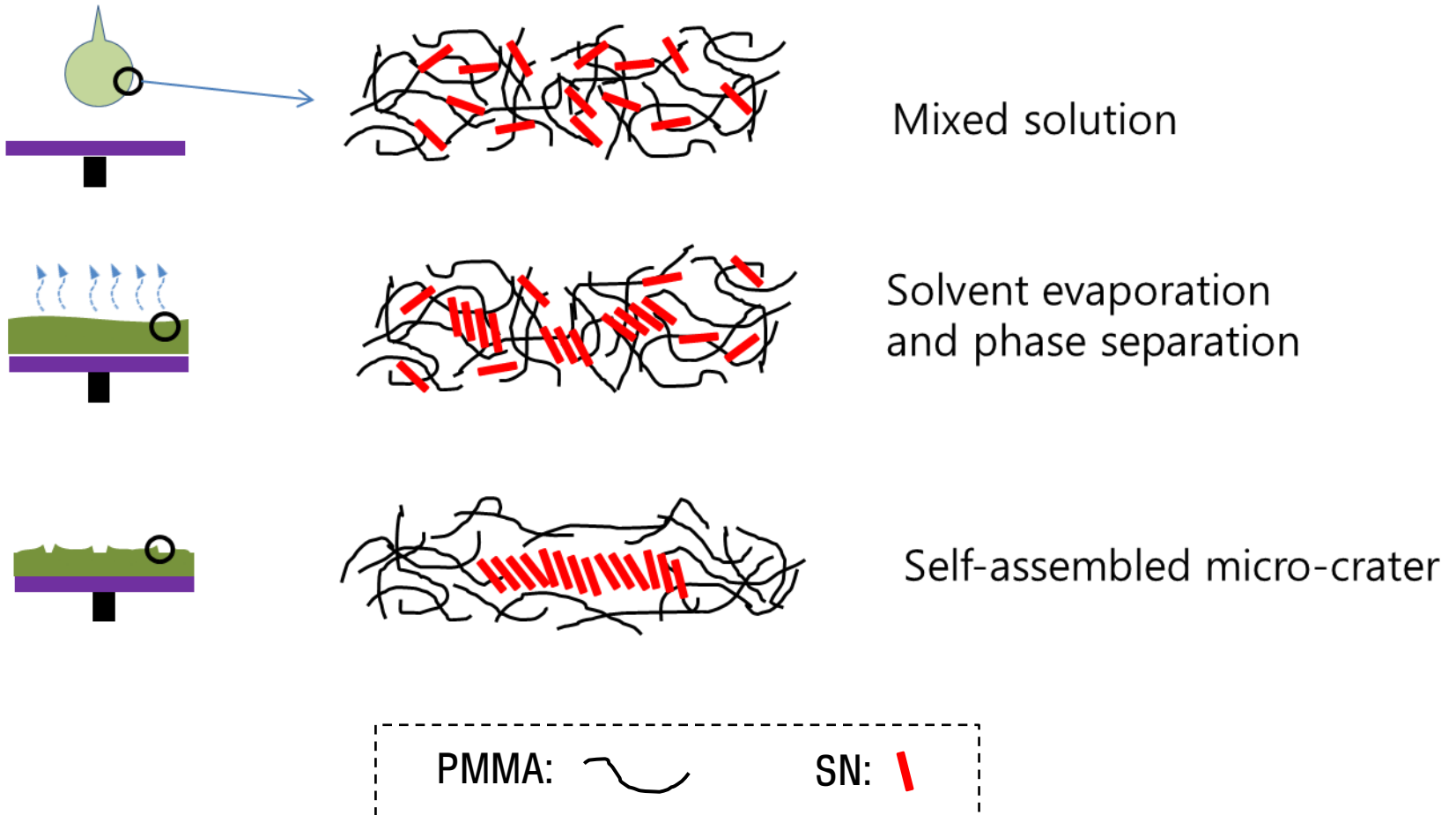


Figure 5. In situ XPS spectra of (a) C 1s and (b) N 1s regions measured as a function of PMMA 30mg/ml SN 1wt%.

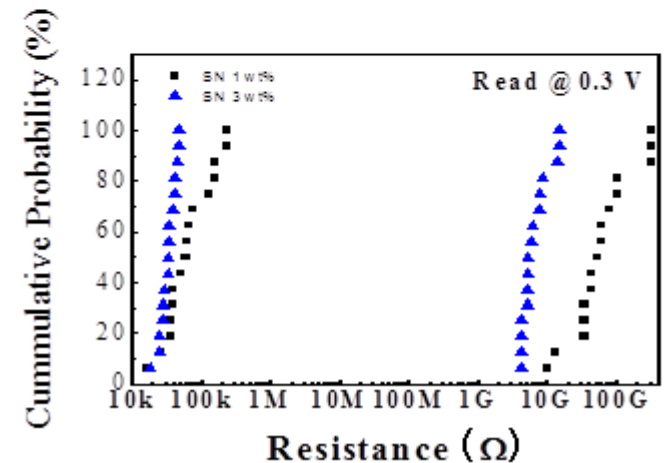
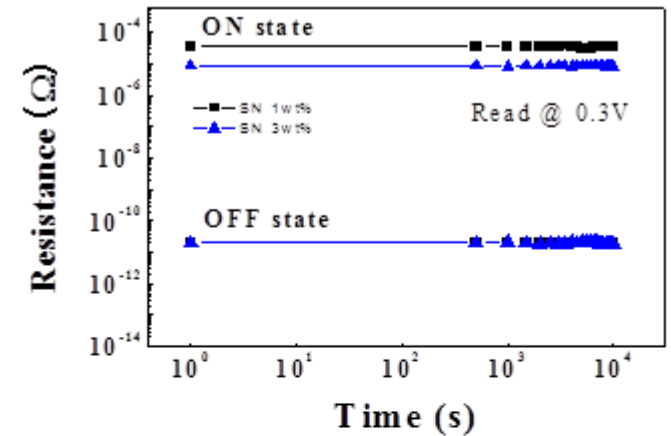
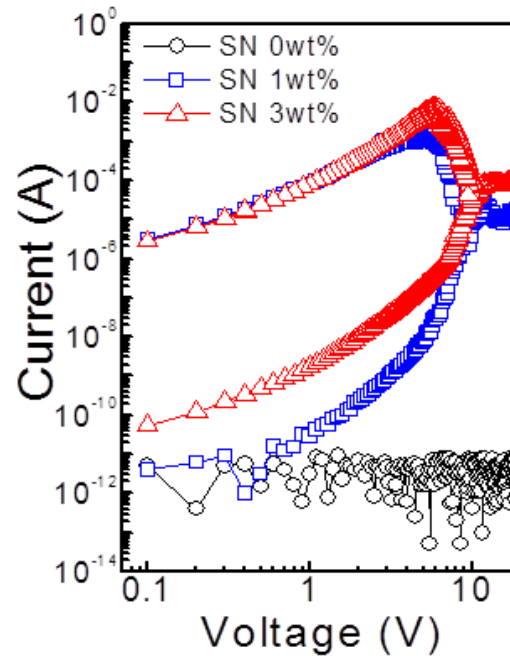
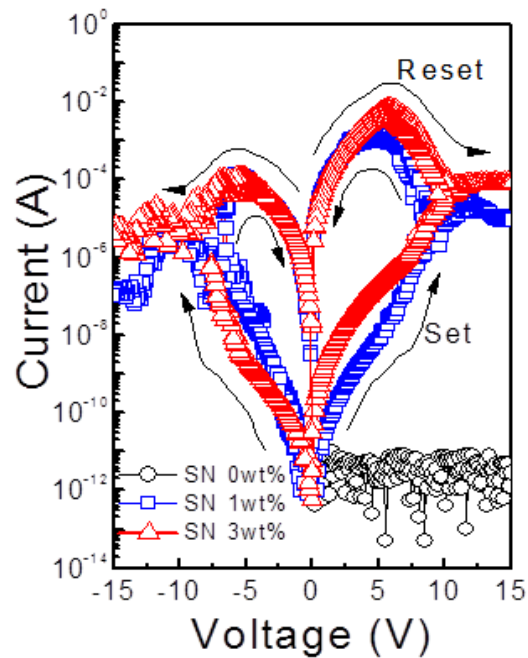
Self-assembled Organic Composite Non-volatile Memory

- Formation of micro craters



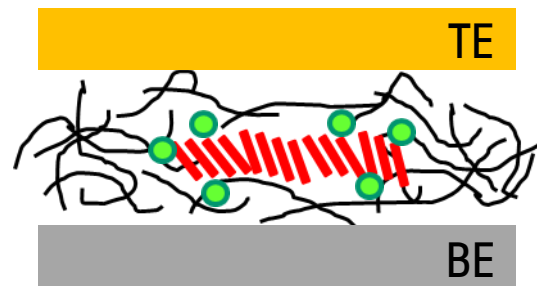
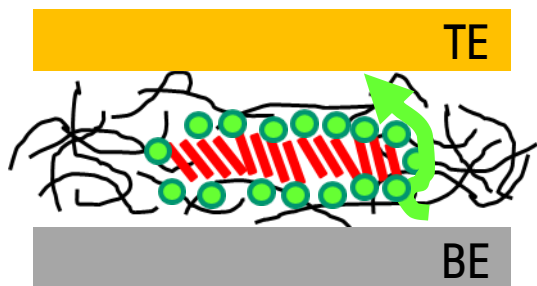
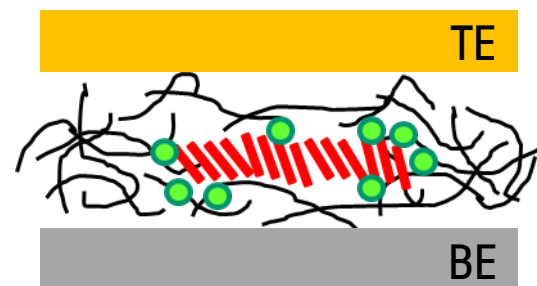
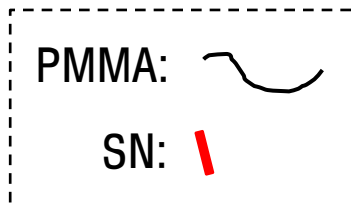
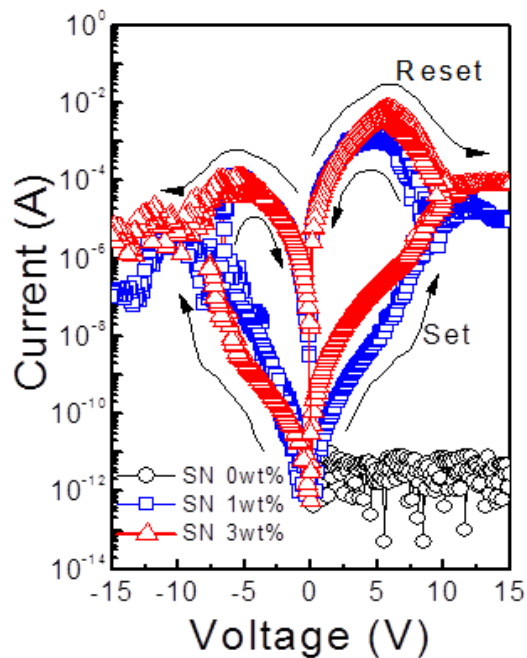
Self-assembled Organic Composite Non-volatile Memory

- Electrical properties of PMMA:SN composite film

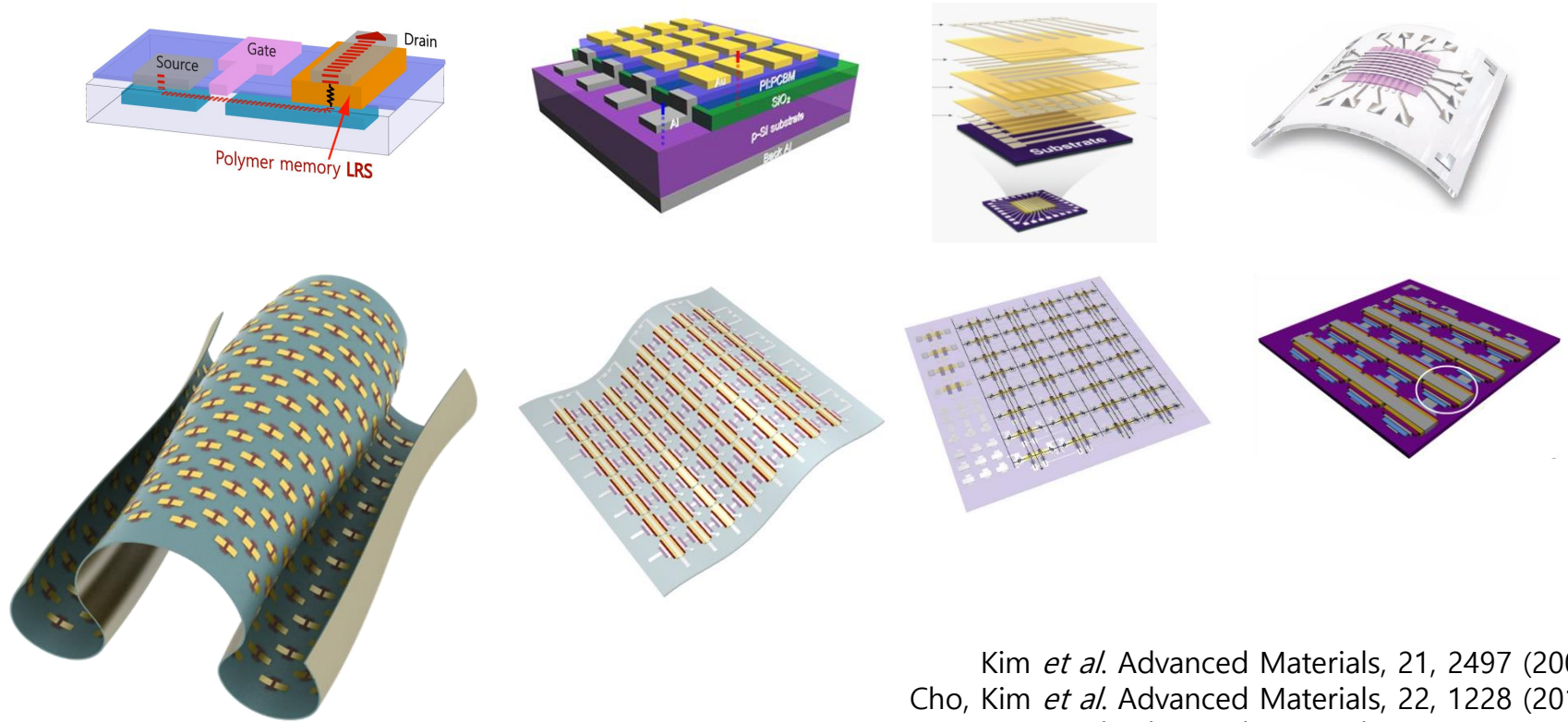


Self-assembled Organic Composite Non-volatile Memory

- Potential switching mechanism



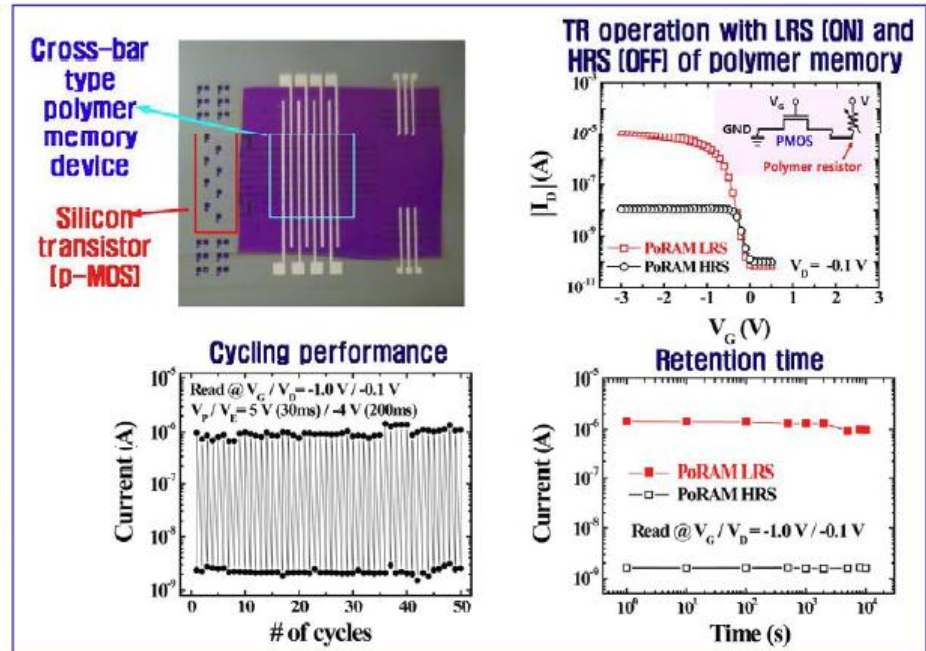
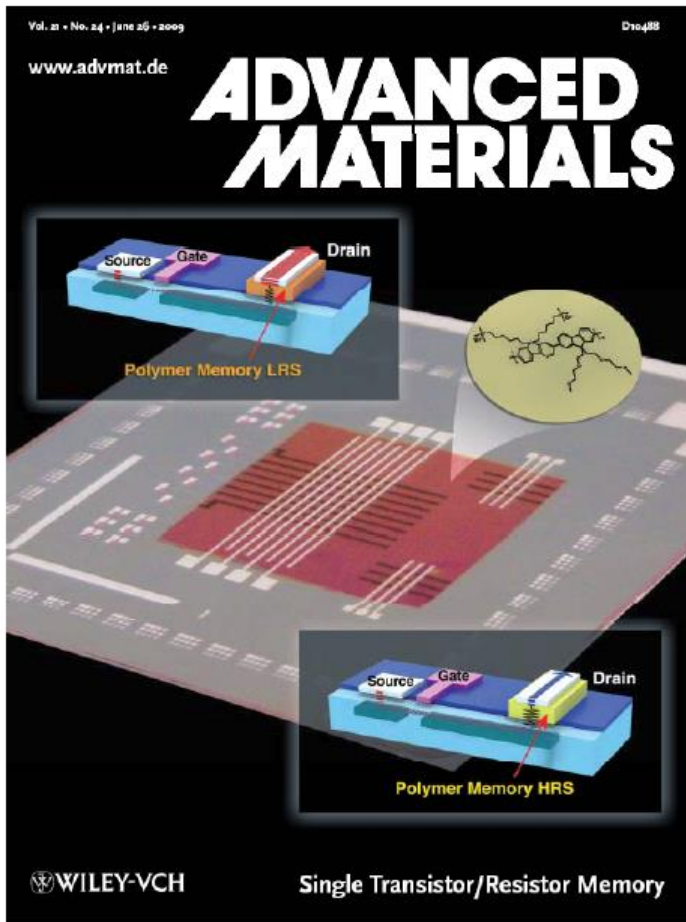
Advanced Architecture for Organic Non-volatile Memory



- Kim *et al.* Advanced Materials, 21, 2497 (2009)
Cho, Kim *et al.* Advanced Materials, 22, 1228 (2010)
Ji, Kim *et al.* Advanced Materials, 22, 3071 (2010)
Song, Kim *et al.* Advanced Materials, 22, 5048 (2010)
Kim *et al.* Advanced Materials, 24, 828 (2012)
Ji *et al.* Nature Communications, 4:2707 (2013)
Ji *et al.* Organic Electronics, 18, 77 (2015)
Ji *et al.* Organic Electronics, 29, 66-71 (2016)
Jang *et al.* In Revision (2018)

Advanced Architecture for Organic Non-volatile Memory

- 1T-1R Organic Memory Device

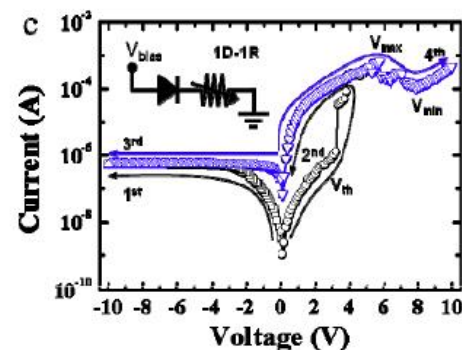
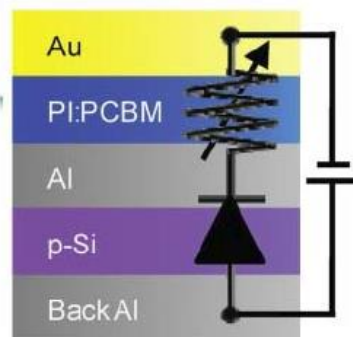
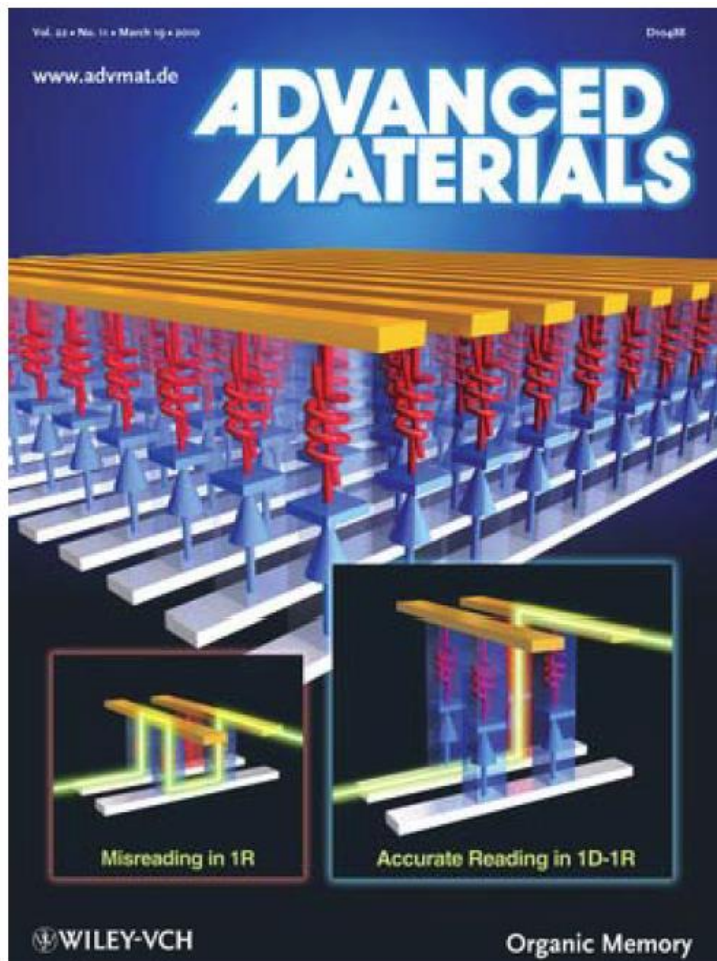


Kim *et al.* Advanced Materials, 21, 2497 (2009)

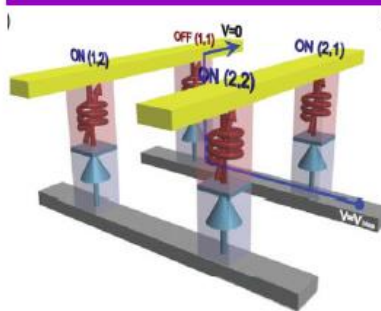
COVER

Advanced Architecture for Organic Non-volatile Memory

- 1D-1R Organic Memory Device



❖ Accurate reading process in 1D-1R array



f)

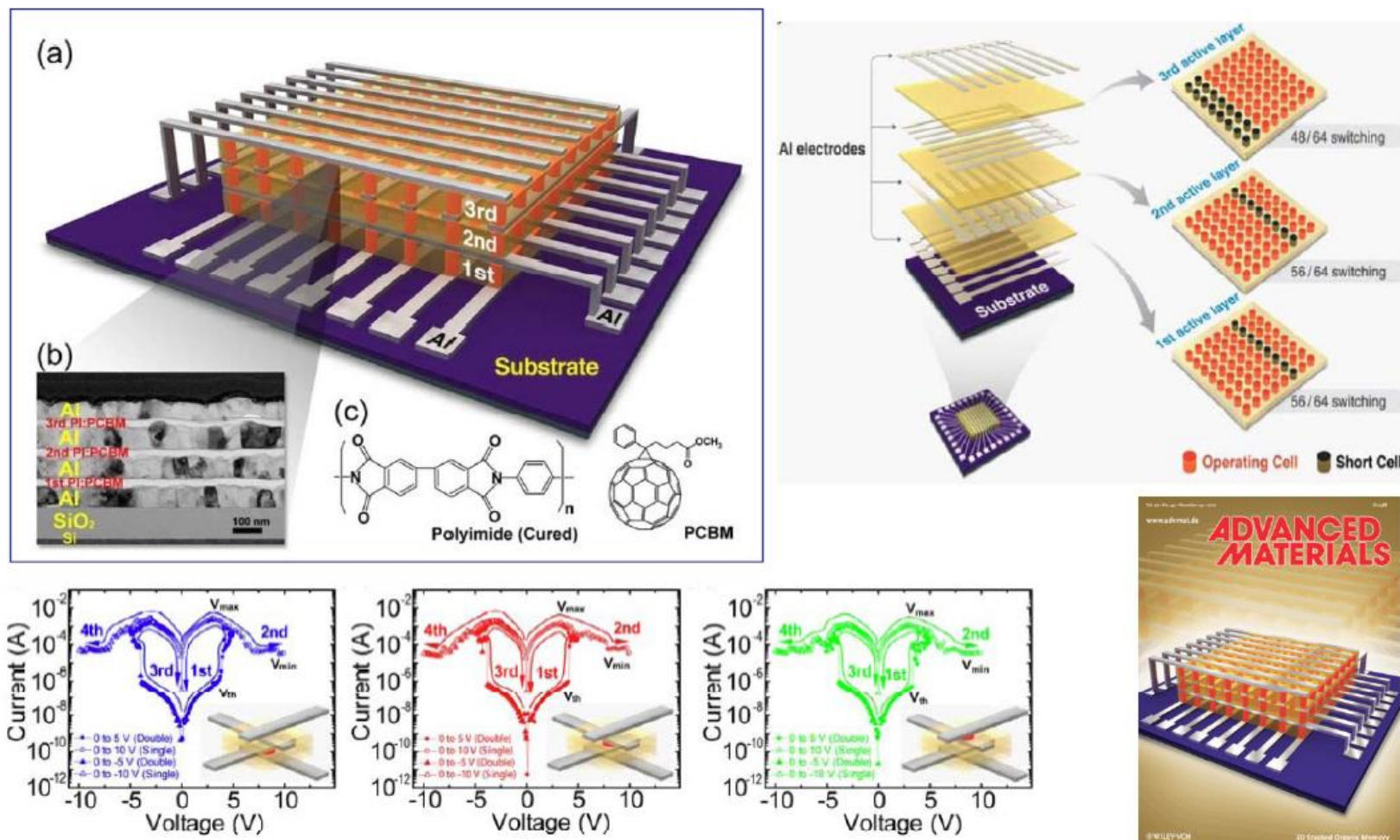
Resistance (Ω) in 1D1R		
W/L \ B/L	1	2
1	4.2 M (OFF)	27.3 K (ON)
2	24 K (ON)	16.3 K (ON)

Cho, Kim *et al.* Advanced Materials, 22, 1228 (2010)

COVER

Advanced Architecture for Organic Non-volatile Memory

- 3-D Integrated Organic Non-volatile Memory Cell Array

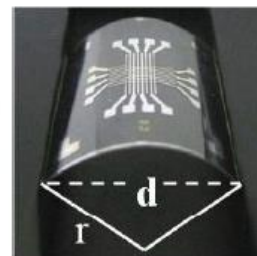
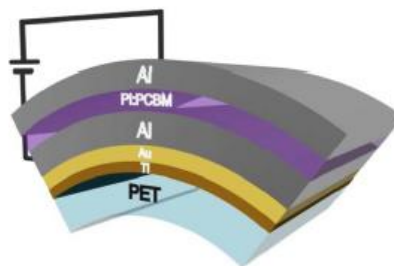
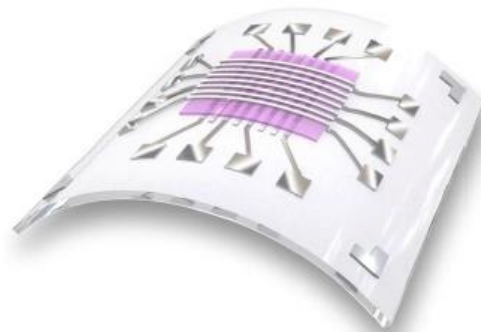


Song, Kim *et al.* Advanced Materials, 22, 5048 (2010)

Advanced Architecture for Organic Non-volatile Memory

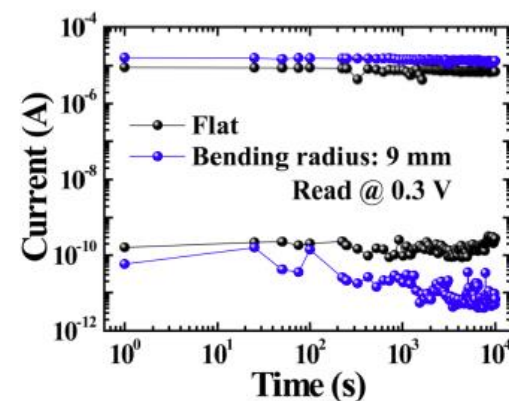
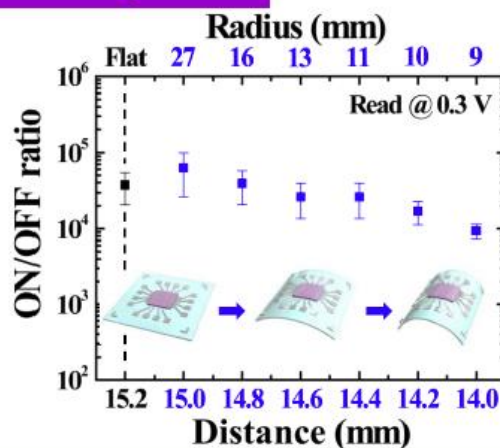
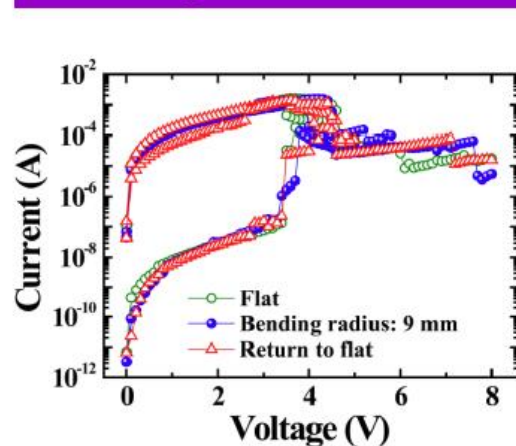
- Flexible Organic Non-volatile Memory

❖ Flexible organic memory device



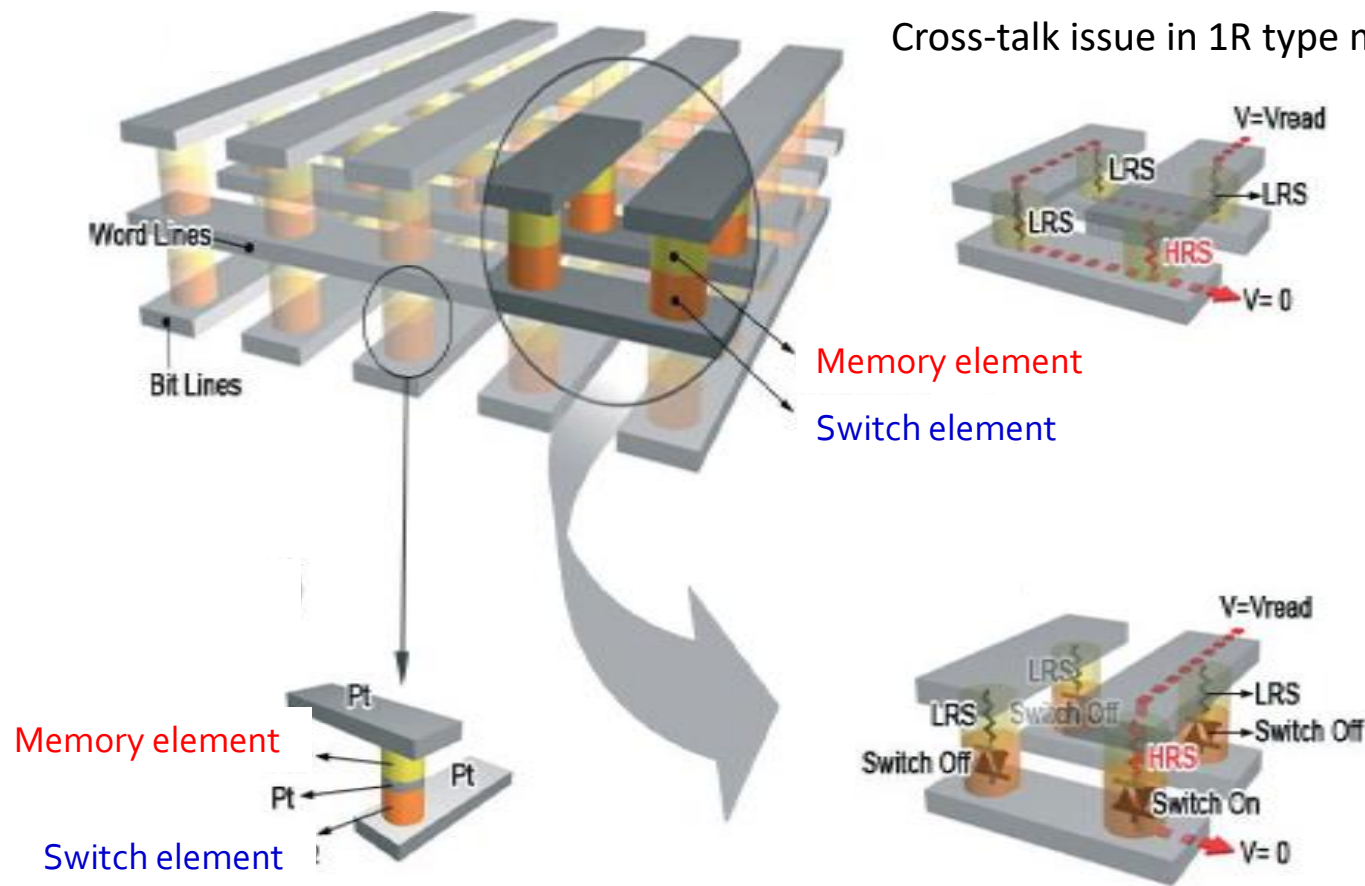
Front Cover

❖ Switching characteristics of flexible memory device



1D-1R Architecture for Organic Non-volatile Memory

- Why 1D-1R Architecture?

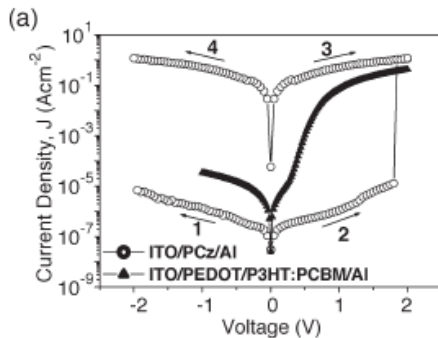
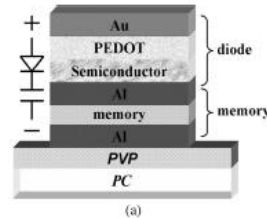
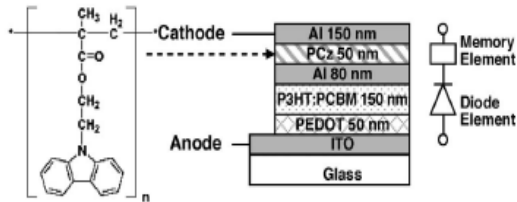


1D-1R Architecture for Organic Non-volatile Memory

- Recent researches on organic 1D-1R

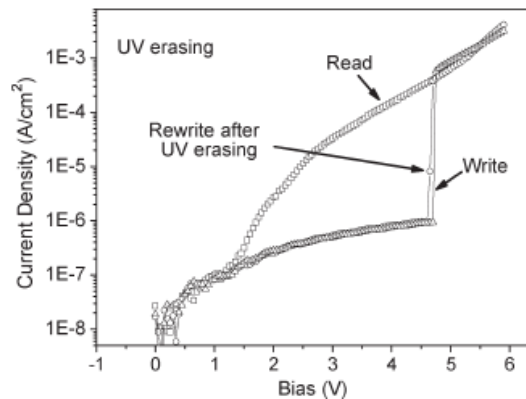
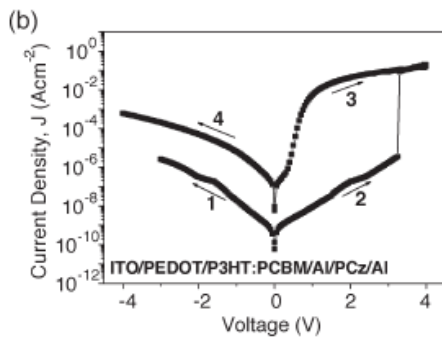
All Organic 1D-1R but WORM type: No isolated cell

hybrid 1D-1R: Rewritable



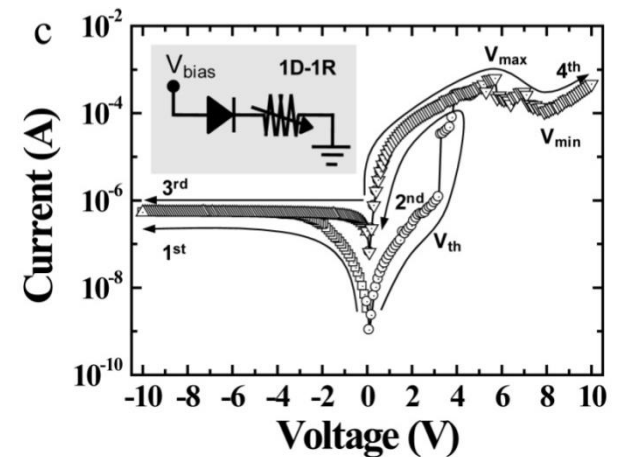
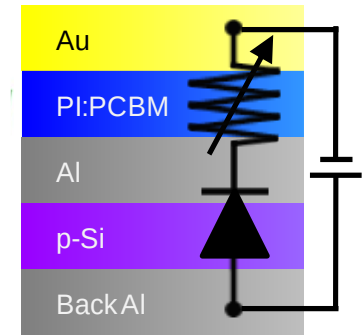
Memory layer: Gold nanoparticles (**Au-PC m**) with a size distribution of 3–5 nm are dissolved in a 4-Cyano-2,4,4-trimethyl-2-ethylsulfanyltiicarbonylsulfanyl- poly (butyric acid 1-adamantan- 1-yl-1-methyl-ethyl ester) (**PC m**)

Diode layer: P3HT/PEDOT:PSS



Teo *et al*, IEEE EDL, 30,489 (2009)

Lin *et al*, IEEE EDL, 30,18 (2009)



Cho, Kim *et al*, Advanced Materials, 22, 1228 (2010)

1D-1R Architecture for Organic Non-volatile Memory

- All organic patternable 1D-1R Organic Non-volatile memory cell array

Issues on organic memory device (resistive change type)

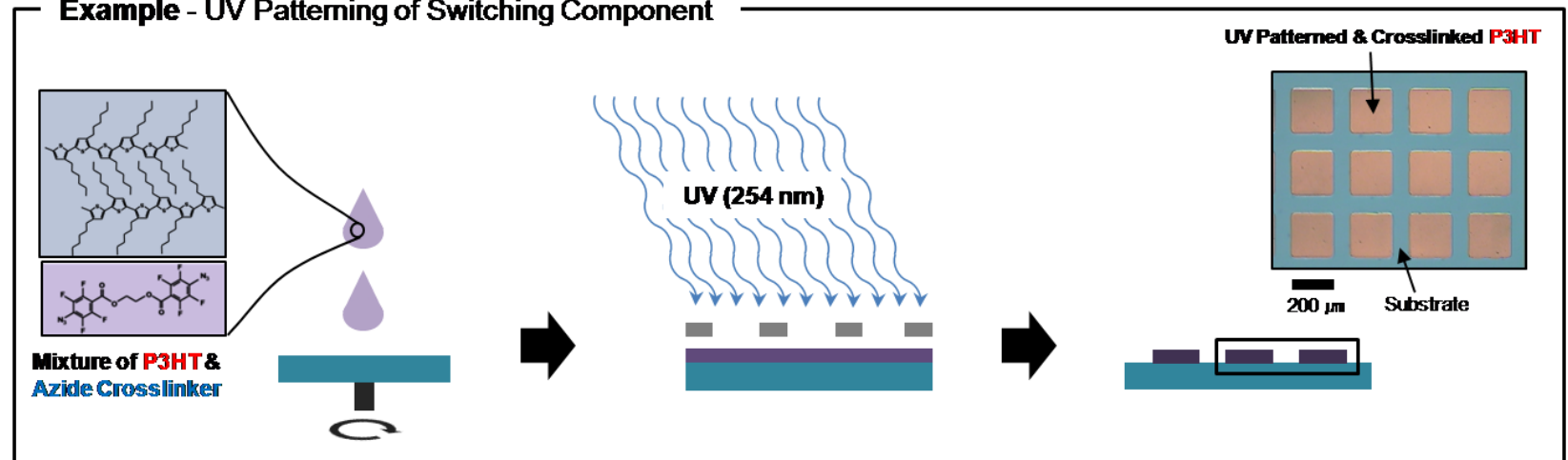
- Processability
- How to Integrate
- Development of novel architecture

Strategy to achieve better processability and device integration

➔ UV patterning & crosslinking for further process

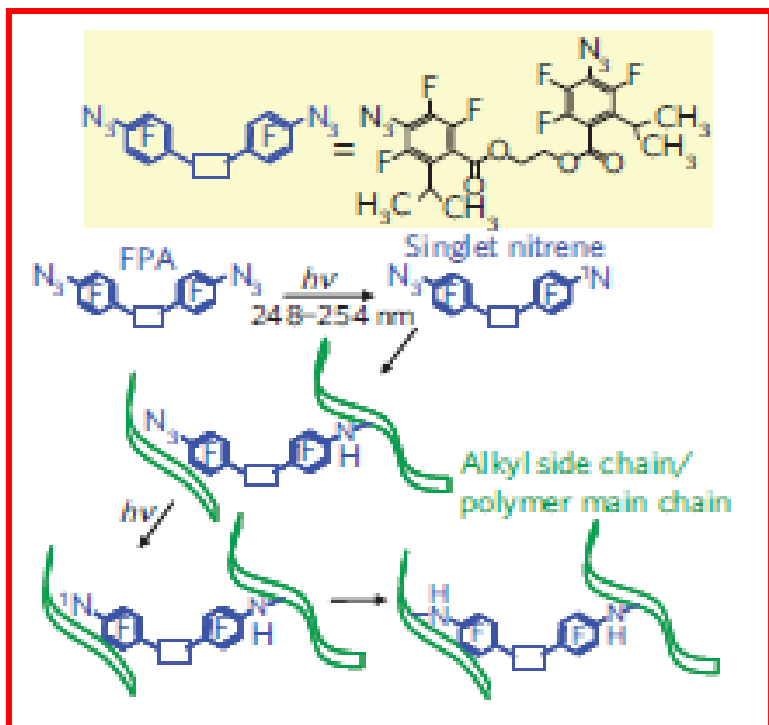
- Use of UV patternable polymer (**Memory component** : Resistor)
- Azide crosslinker for patterning of common conjugated polymers (**Switching Component**: Diode)

Example - UV Patterning of Switching Component



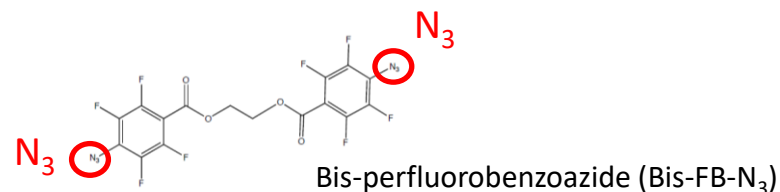
1D-1R Architecture for Organic Non-volatile Memory

Small molecule for cross linking of organic materials

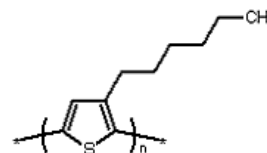


Bis(perfluorophenyl azide)s (sFPAs) can be mixed generally into polymer OSCs to cause photocrosslinking when exposed to deep-ultraviolet light (DUV, 254nm wavelength) **without degrading their essential semiconductor properties.**

• Our Cross linker



• p-type polymer material



Poly(3-hexylthiophene) (P3HT)

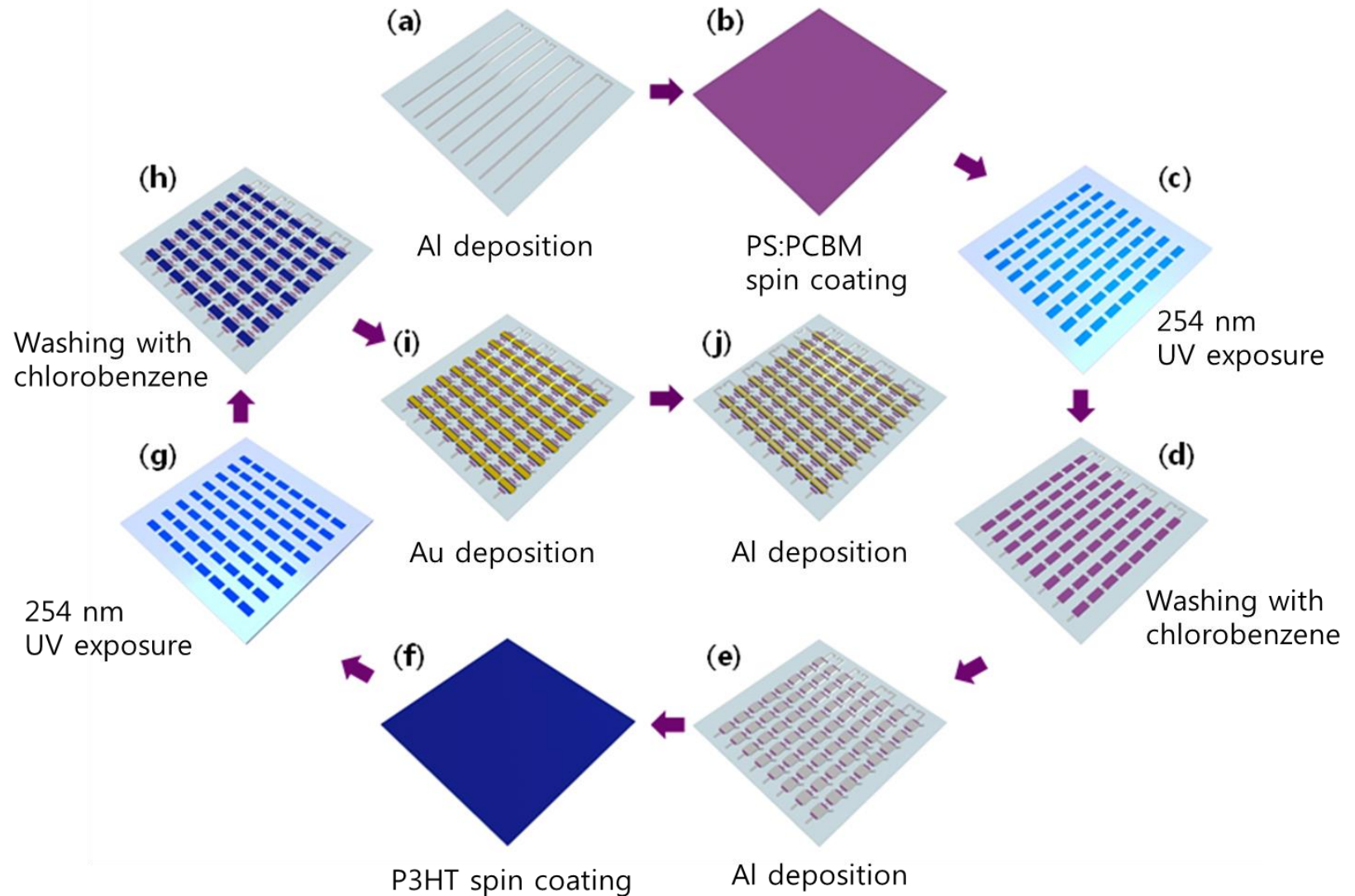
• UV source



Wavelength: 254nm, 4W

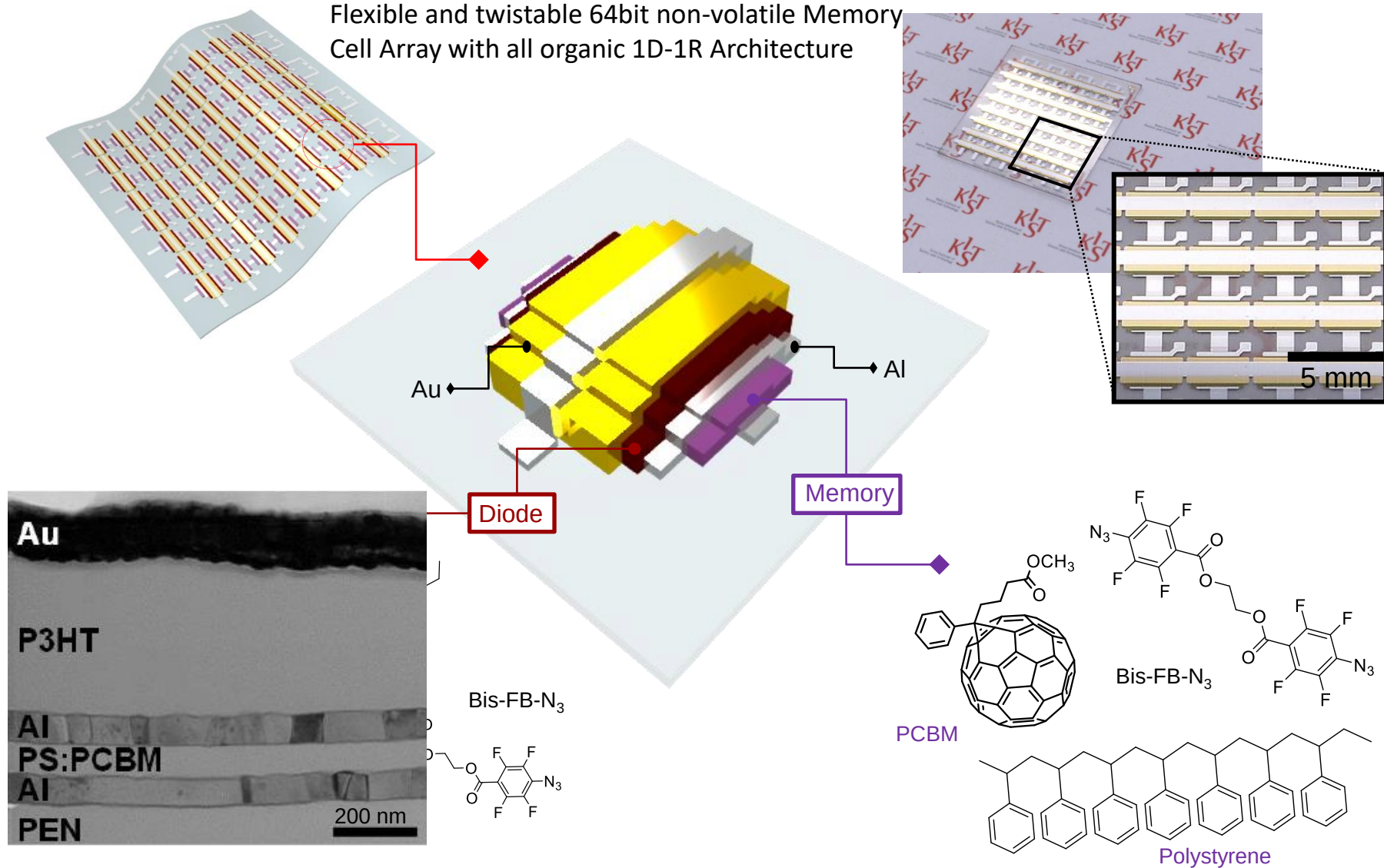
1D-1R Architecture for Organic Non-volatile Memory

- Fabrication procedure of All organic flexible one resistor-one diode cell array



1D-1R Architecture for Organic Non-volatile Memory

Flexible and twistable 64bit non-volatile Memory
Cell Array with all organic 1D-1R Architecture



1D-1R Architecture for Organic Non-volatile Memory

- I-V characteristics of 1D-1R Organic Non-volatile Memory Cell

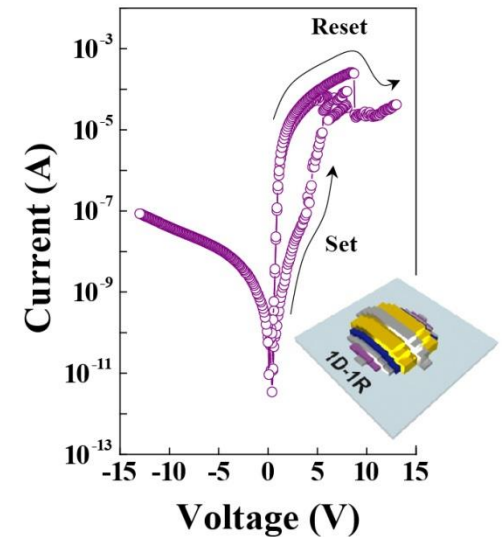
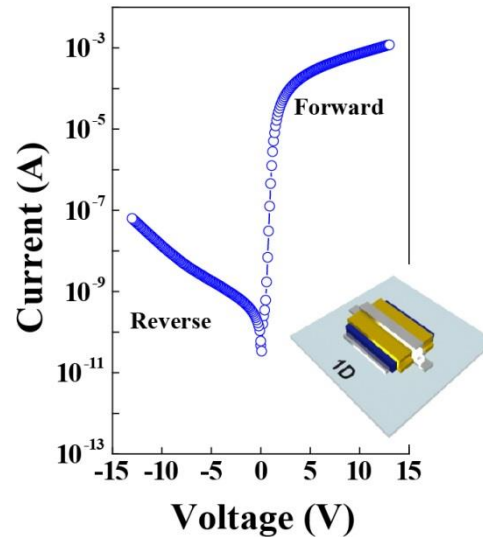
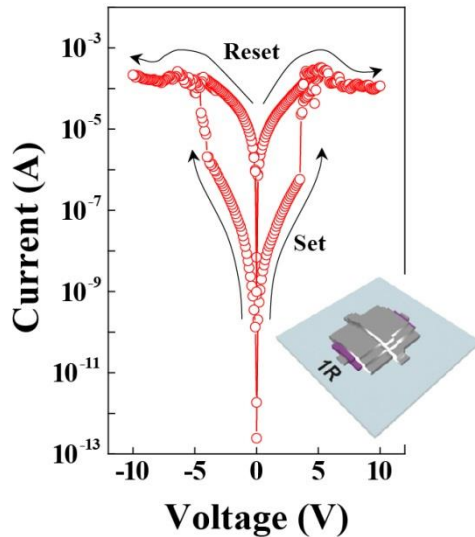
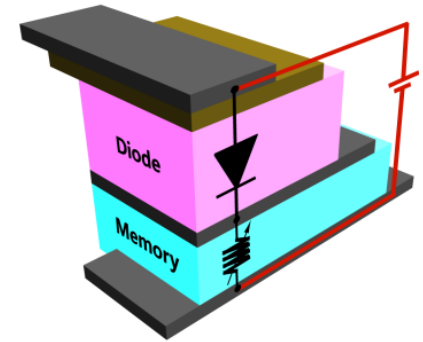
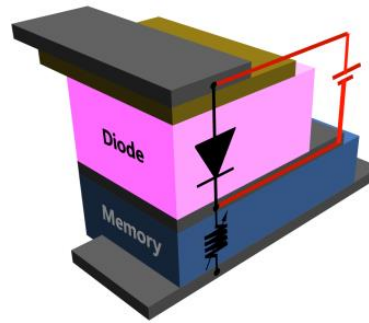
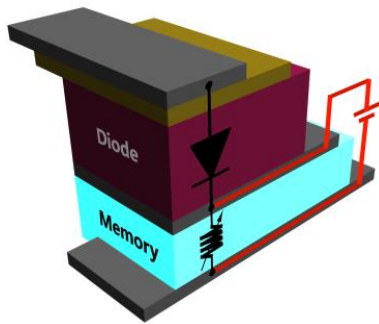
Memory



Diode

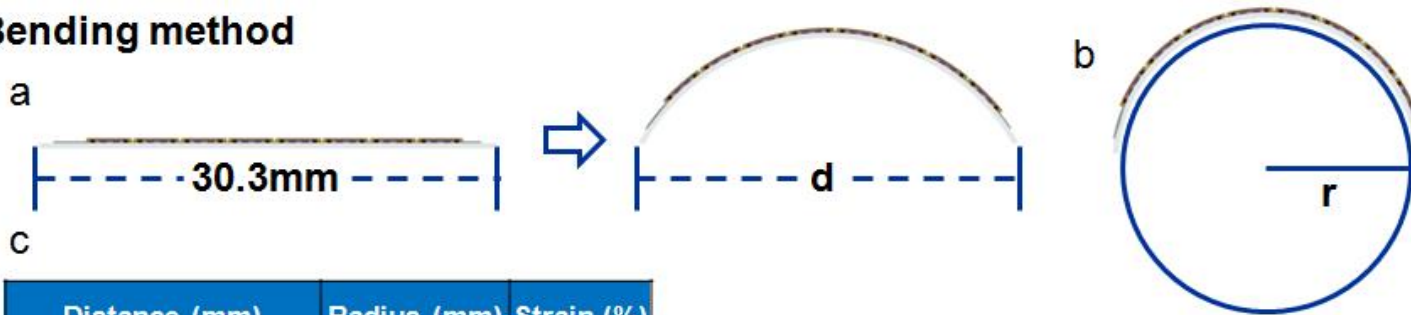


1D-1R



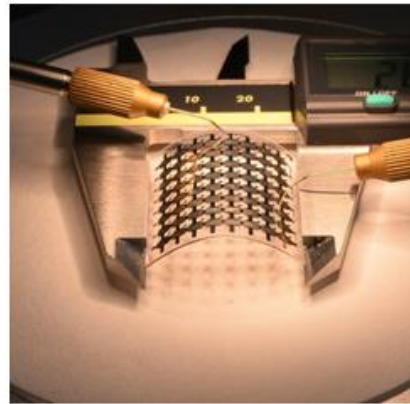
1D-1R Architecture for Organic Non-volatile Memory

Bending method



Distance (mm)	Radius (mm)	Strain (%)
30.30	∞	0.00
29.70	34.00	0.18
29.10	22.03	0.29
28.50	20.00	0.31
27.90	15.80	0.40
27.30	15.50	0.41
26.70	14.10	0.45
26.10	13.00	0.48
22.10	9.60	0.65
18.10	7.60	0.83
14.10	6.20	1.01
10.10	5.00	1.26
6.80 (Glass pipet)	3.40	1.85
6.30 (Breakdown of diode)	3.10	2.03
5.00 (5 sheets of glass)	2.50	2.51
4.00 (4 sheets of glass)	2.00	3.14
3.00 (3 sheets of glass)	1.50	4.19
2.00 (2 sheets of glass)	1.00	6.28
1.00 (1 sheet of glass) (Device is broken)	0.50	12.57

d



e

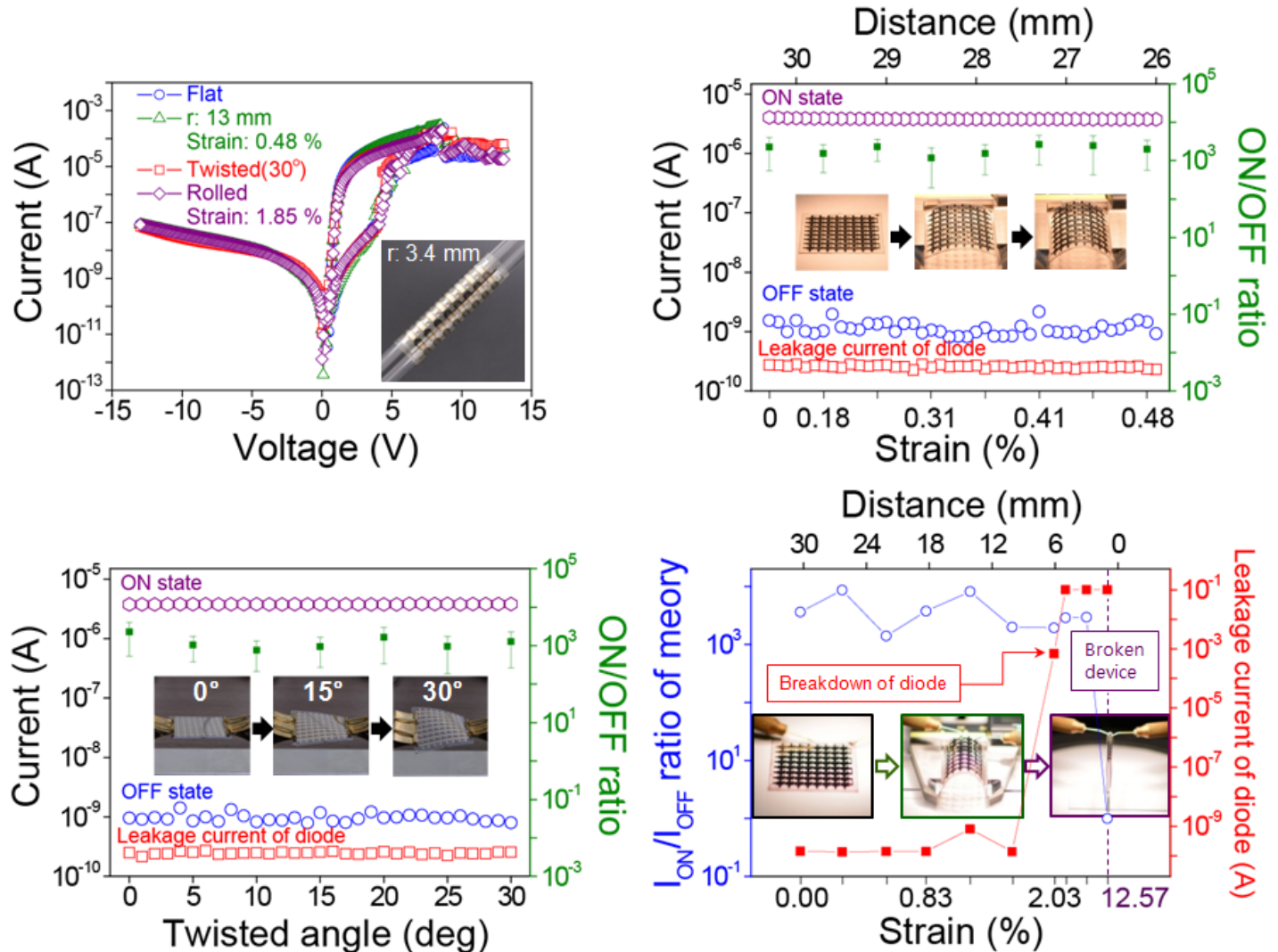


Equation of strain

$$\text{Strain (\%)} = \frac{\text{Total thickness of device}}{2 \times \text{radius of curvature}} \times 100$$

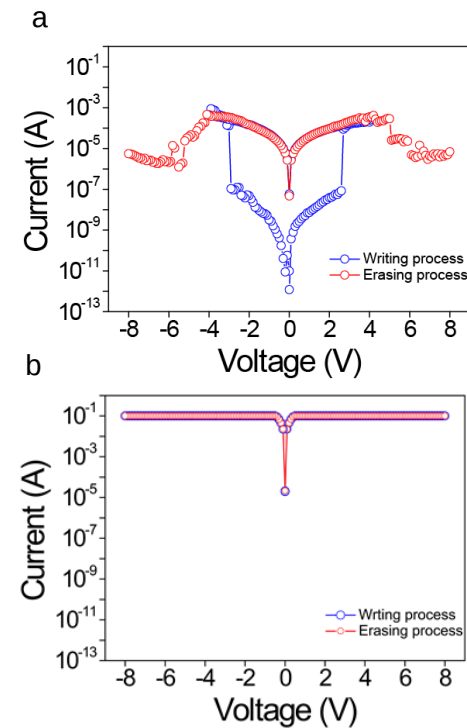
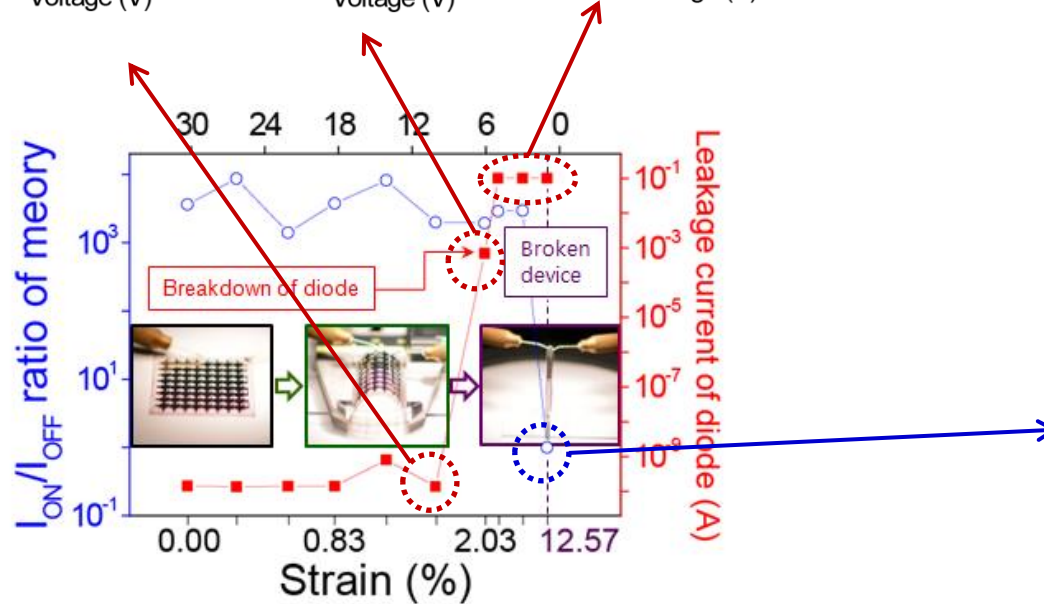
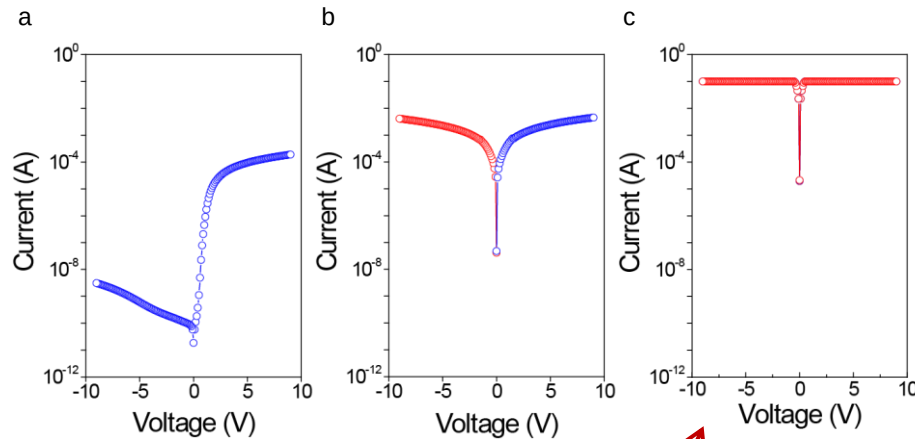
1D-1R Architecture for Organic Non-volatile Memory

- Memory Performances of 1D-1R Under various bending conditions



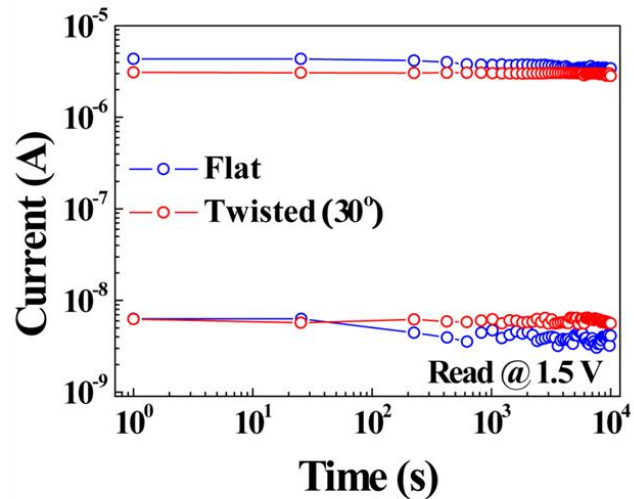
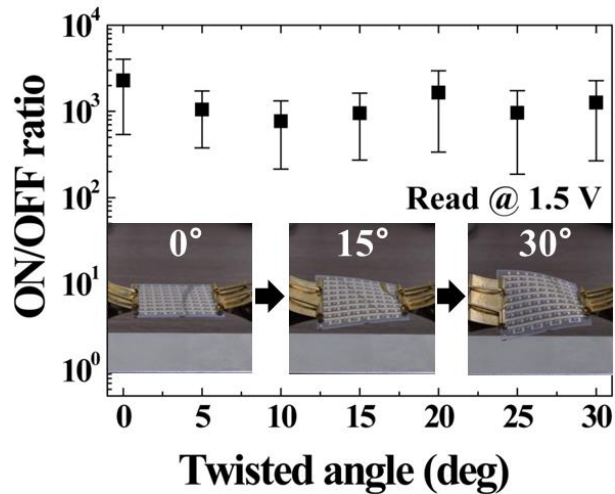
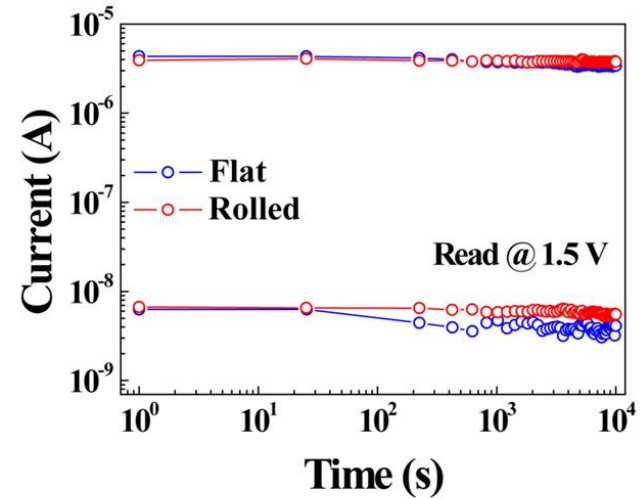
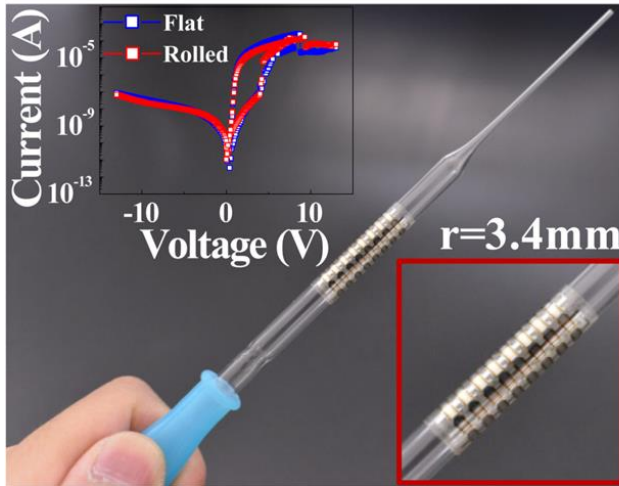
1D-1R Architecture for Organic Non-volatile Memory

- Memory Performances of 1D-1R Under various bending conditions



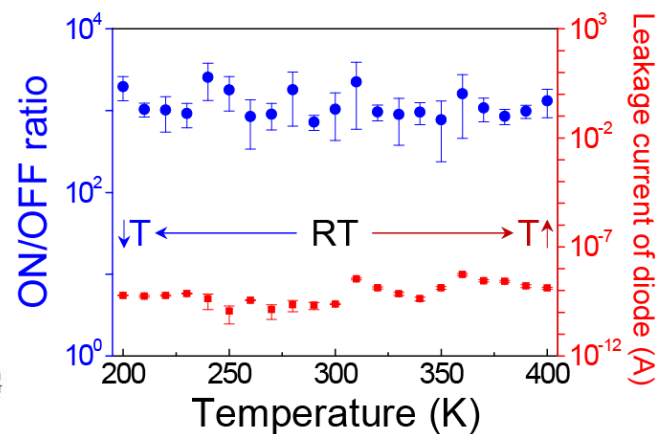
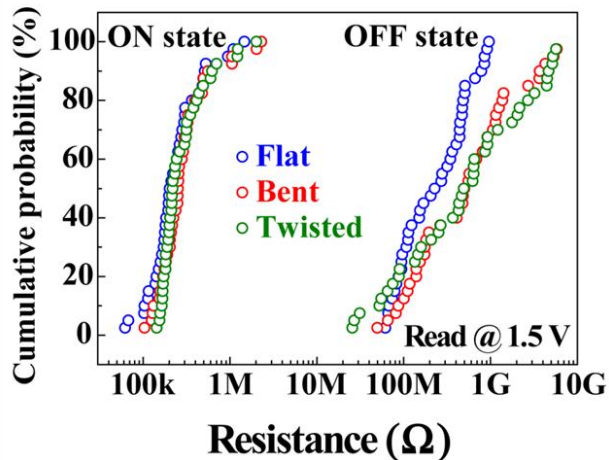
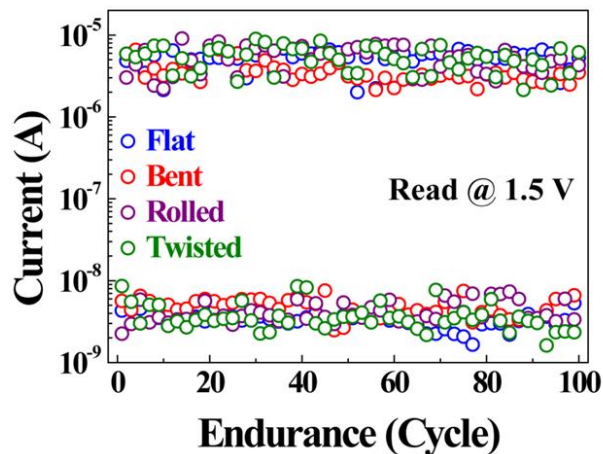
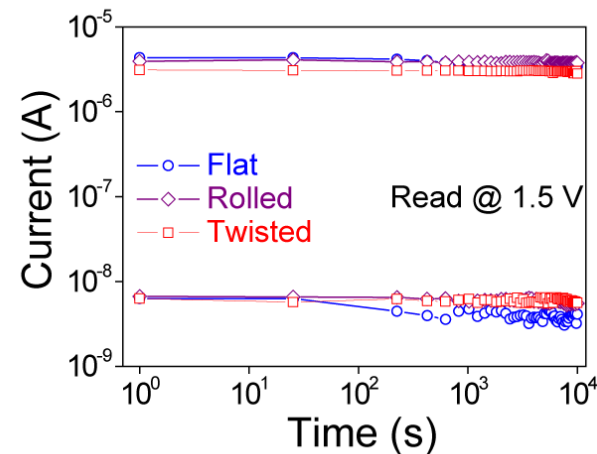
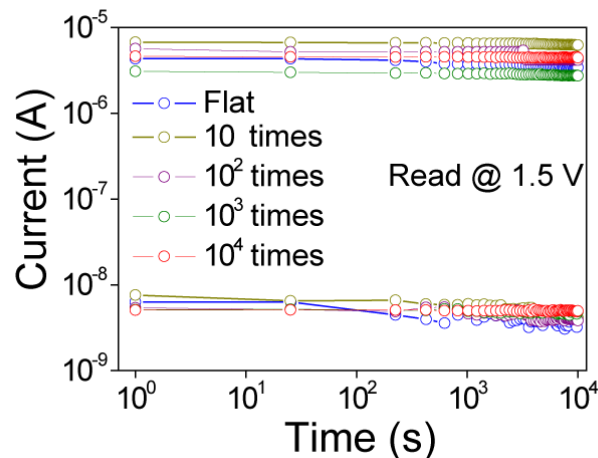
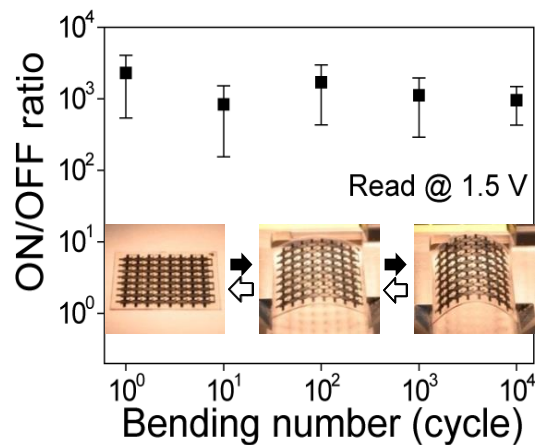
1D-1R Architecture for Organic Non-volatile Memory

- Memory Performances of 1D-1R Under various bending conditions



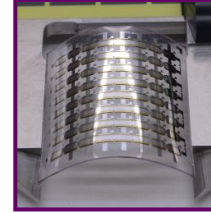
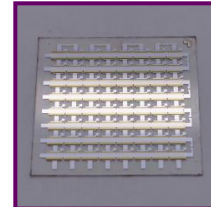
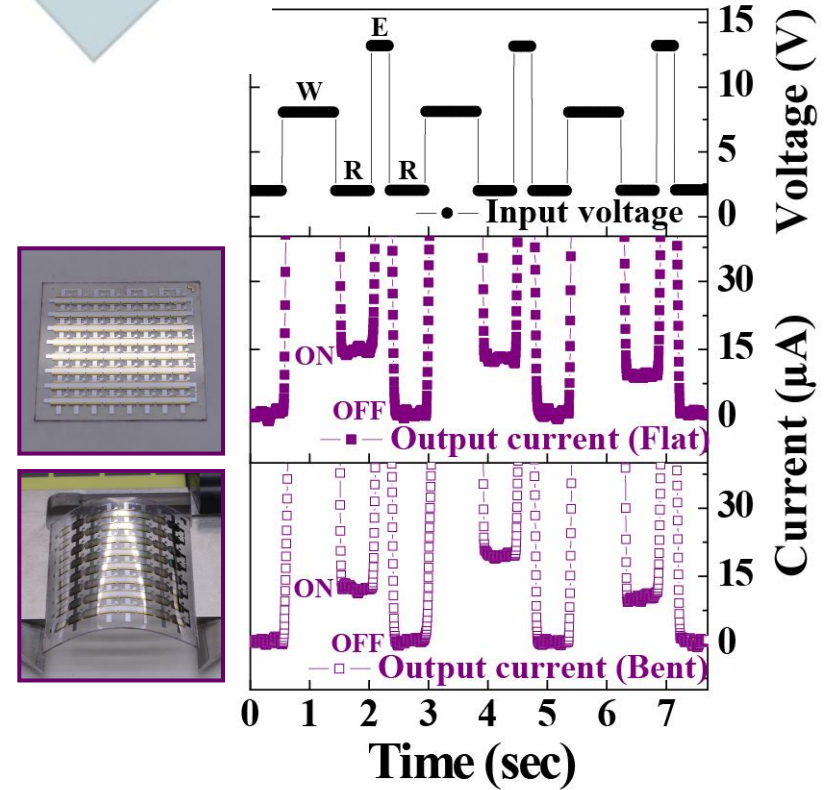
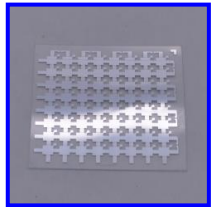
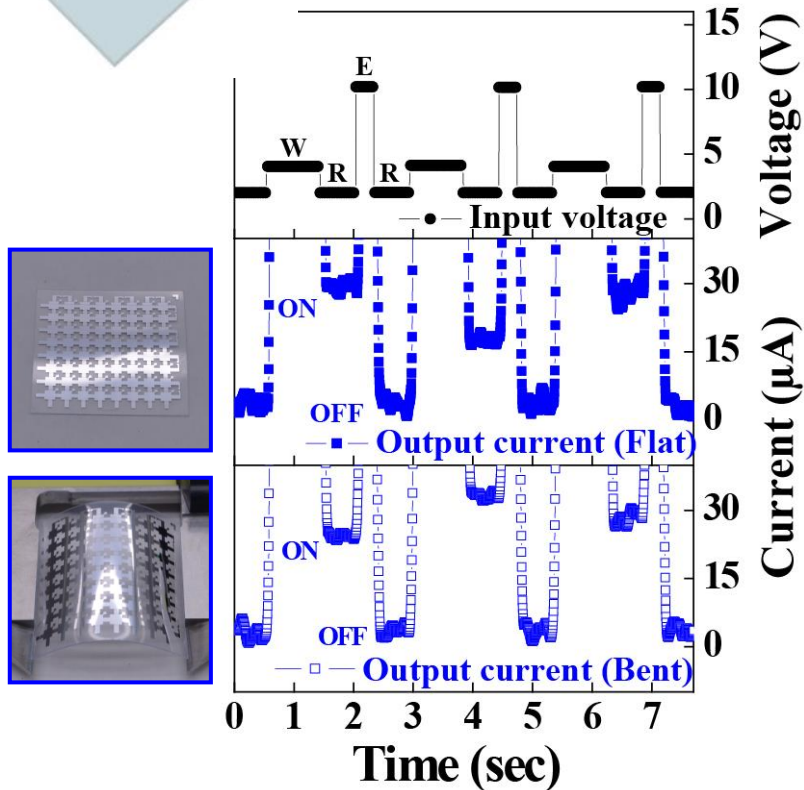
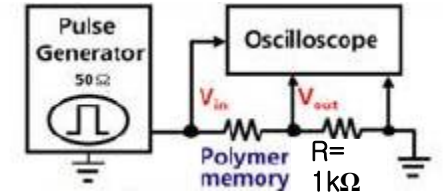
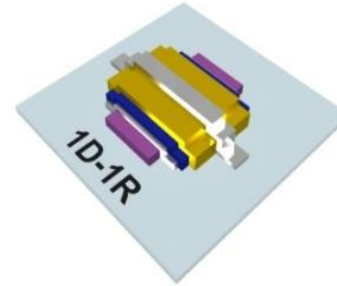
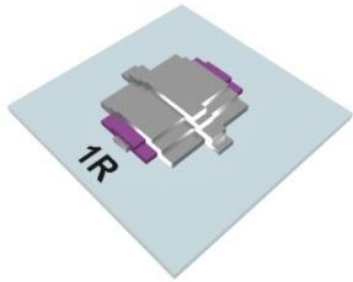
1D-1R Architecture for Organic Non-volatile Memory

- Reliability of 1D-1R Under various bending conditions



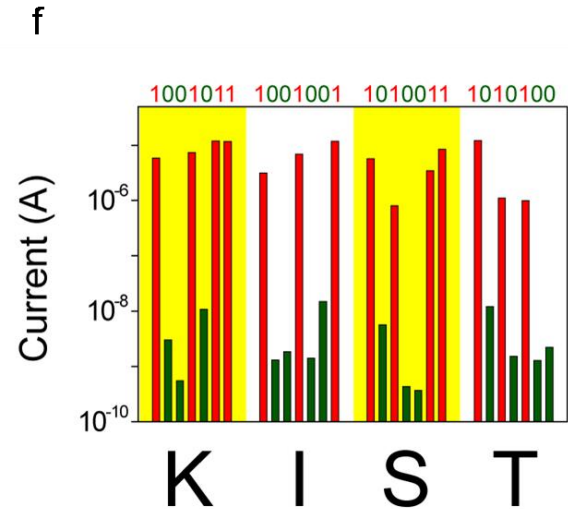
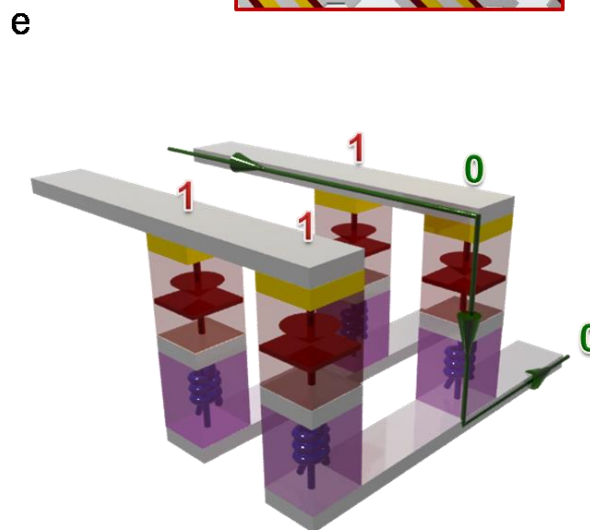
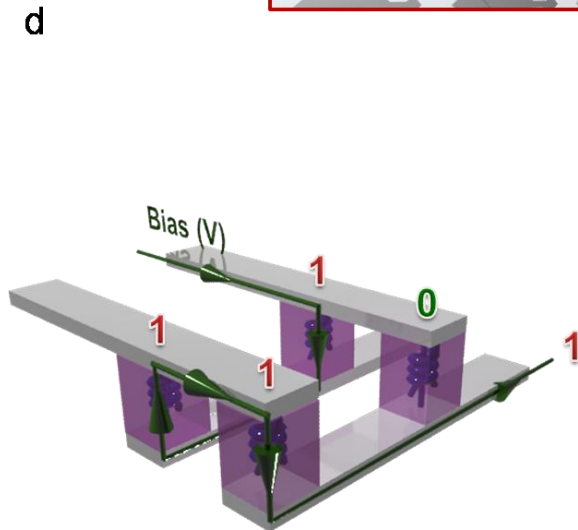
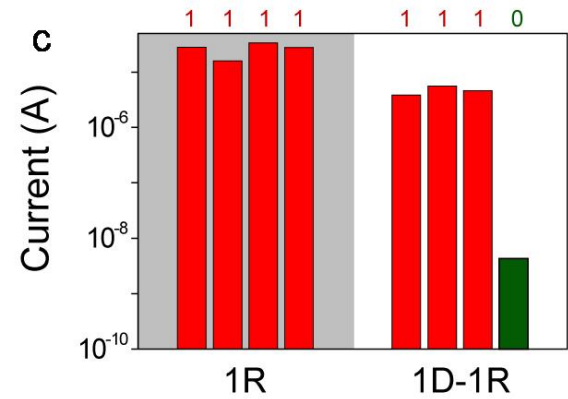
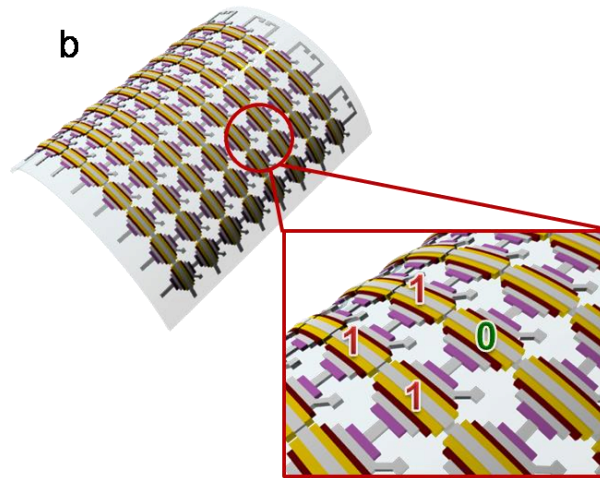
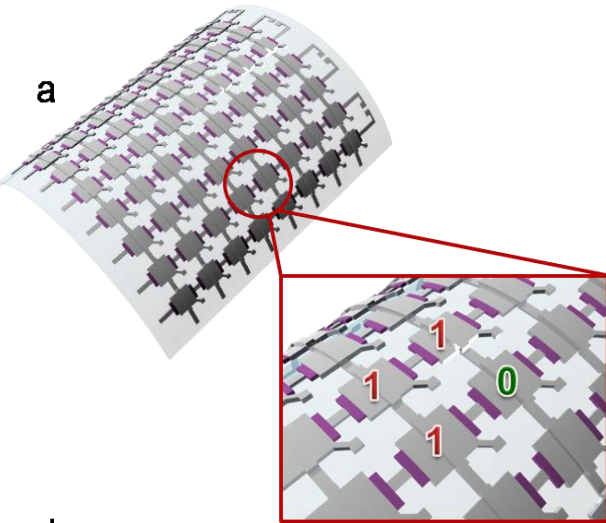
1D-1R Architecture for Organic Non-volatile Memory

- Pulse Response test of bent 1D-1R cell

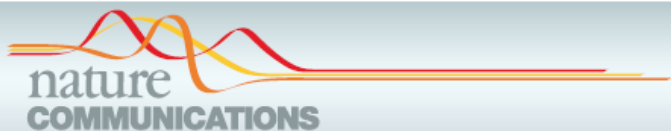


1D-1R Architecture for Organic Non-volatile Memory

- Addressing Test of Flexible **1R** cell array vs. **1D-1R** cell array



1D-1R Architecture for Organic Non-volatile Memory



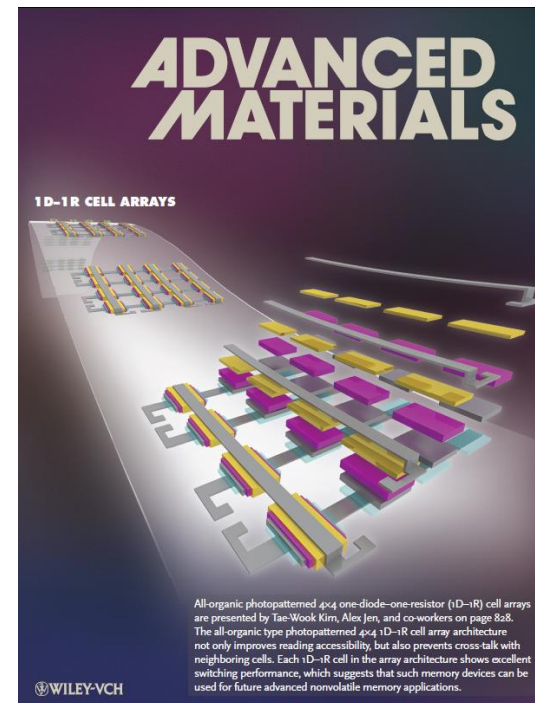
ARTICLE

Received 19 Jul 2013 | Accepted 3 Oct 2013 | Published 1 Nov 2013

DOI: 10.1038/ncomms3707

Flexible and twistable non-volatile memory cell array with all-organic one diode-one resistor architecture

Yongsung Ji^{1,2}, David F. Zeigler³, Dong Su Lee¹, Hyejung Choi⁴, Alex K.-Y. Jen³,
Heung Cho Ko² & Tae-Wook Kim¹



Kim *et al*, Advanced Materials, 24, 828 (2012) [Frontispiece of advanced materials](#)

Ji *et al*, Nature Communications 4:2707 | DOI: 10.1038/ncomms3707 (2013)

Organic Non-volatile Memory Transistors

Organic Non-volatile Memory Transistors

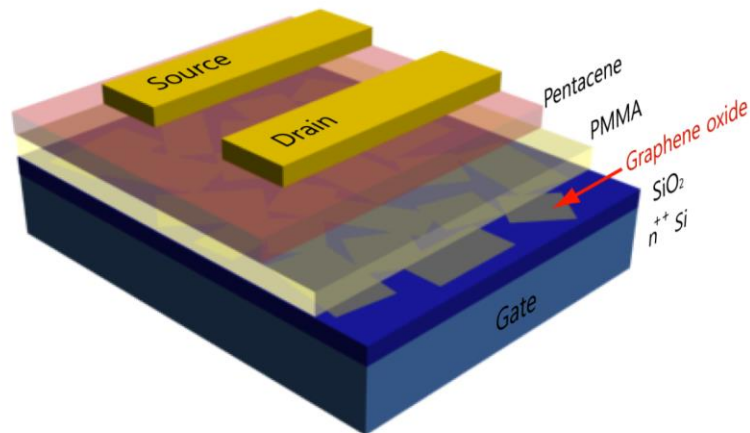
Low voltage memory transistor with hybrid gate dielectrics

Organic transistors with small molecule charge trap layers

One step synthesis of Au nanoparticle-cyclized polyacrylonitrile composite films

Graphene quantum dots for organic non-volatile memory transistors

Control of ferroelectricity of P(VDF-TrFE) copolymer via photocrosslinking



Kim *et al*, Applied Physics Letters 97, 023310 (2010)

Kim *et al*, Organic Electronics 15, 2775 (2014)

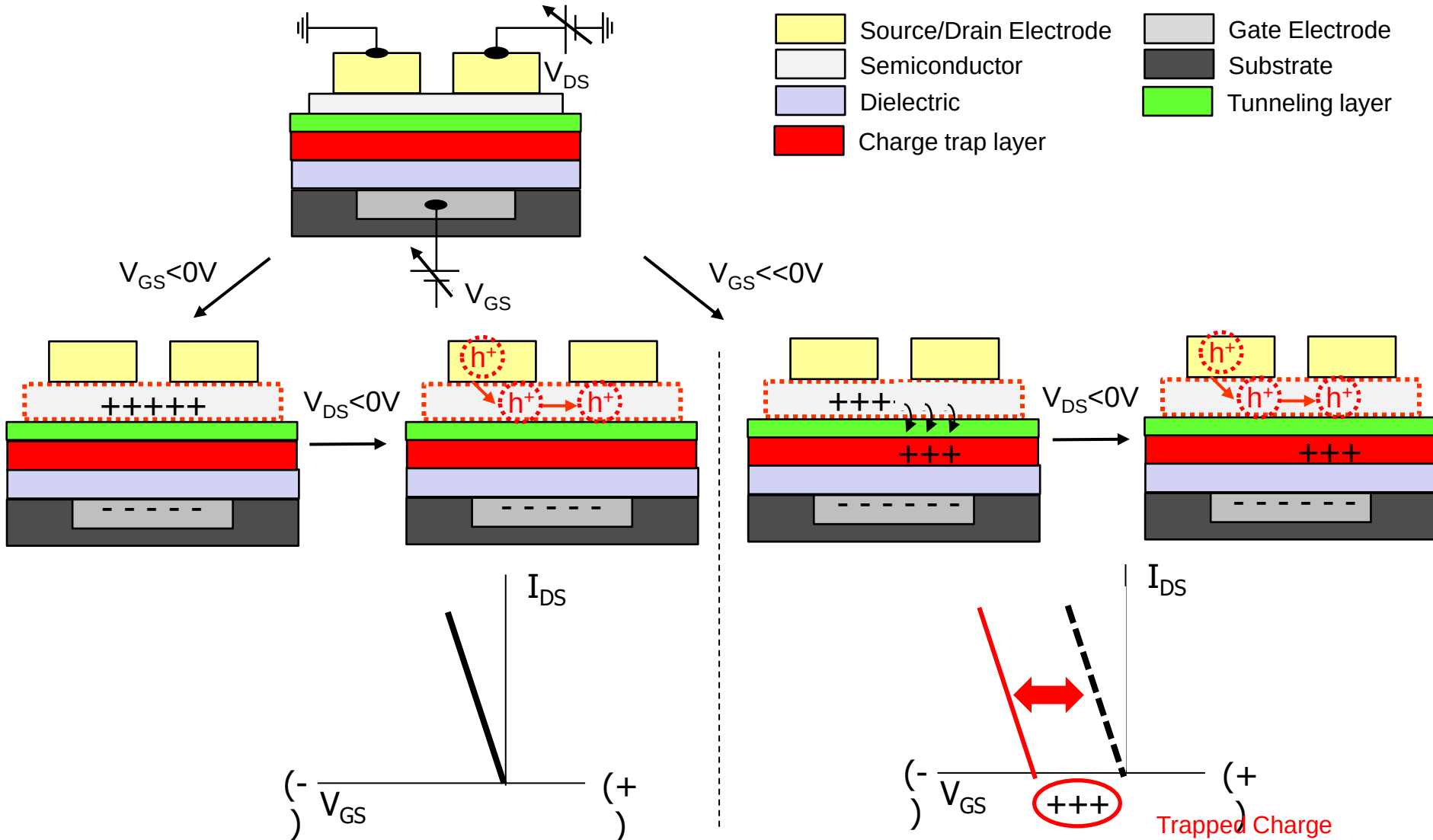
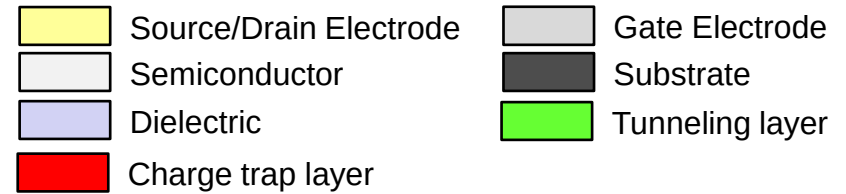
Cho *et al*, Journal of Materials Chemistry C, 4, 1511 (2016)

Ji *et al*, Nanotechnology, 27, 145204 (2016)

Jang *et al*, Manuscript in preparation (2017)

Operation of Organic Memory Transistors

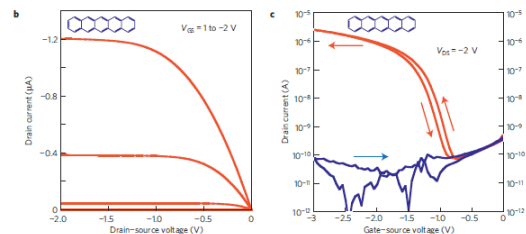
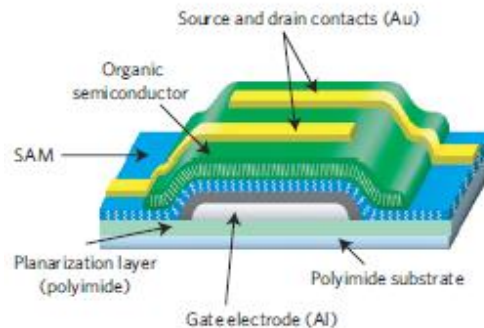
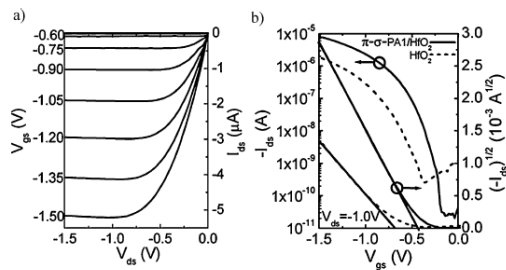
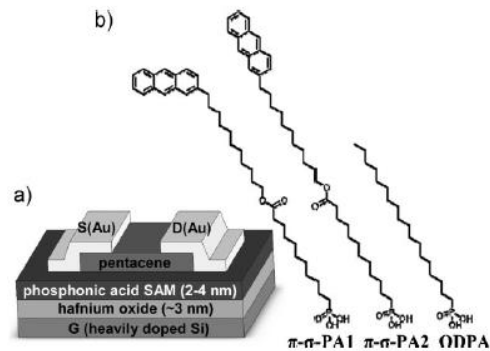
(P-channel Operation)



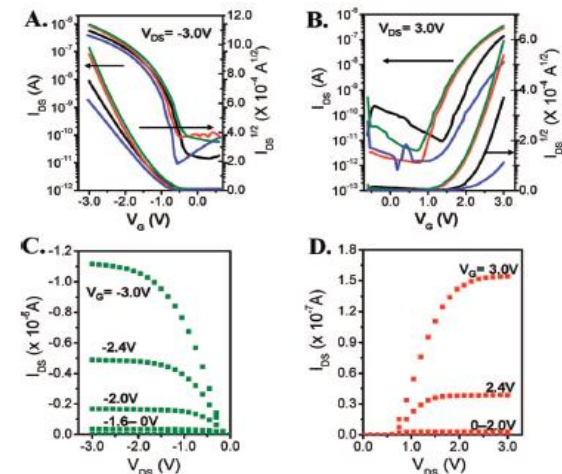
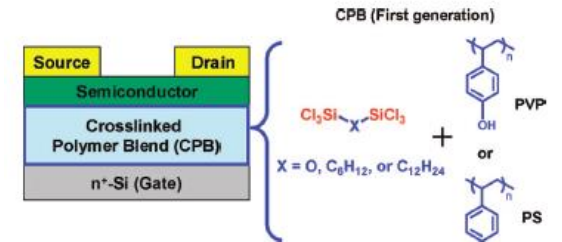
Previous Research on Organic Memory Transistors

- Researches low voltage organic field effect transistors

Hybrid gate dielectric



Ultrathin organic gate dielectrics



O. Acton et al, **Adv. Mater.**, 20, 3697 (2008) T. Sekitani et al, **Nature Mat.**, Vol 9, 1015 (2010)

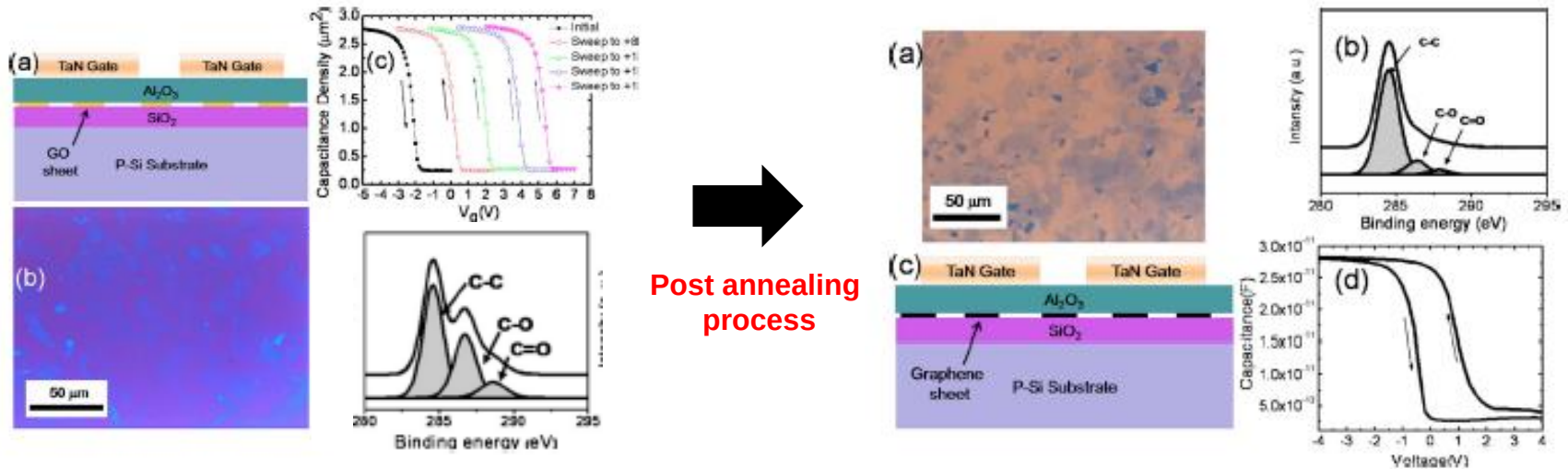
C. Kim et al, **JACS**, 130, 6867 (2008)

Hybrid gate dielectrics such as sol-gel HfOx+SAMs or AlOx+SAMs and Ultrathin organic gate dielectrics are widely used for low voltage organic field effect transistors.

→ If we use graphene oxide layer as a charge trap layer in this low voltage OFET platform, we are able to demonstrate low voltage organic memory transistors.

Previous Research on Organic Memory Transistors

- Why graphene oxide for organic memory transistors?



In flash type memory device, post annealing is necessary for achieving dense blocking oxide (Al_2O_3 , in this case). However this post annealing process reduces graphene oxide to graphene and that has poor charge trap behavior than that of graphene oxide (narrowing CV hysteresis after post annealing process)

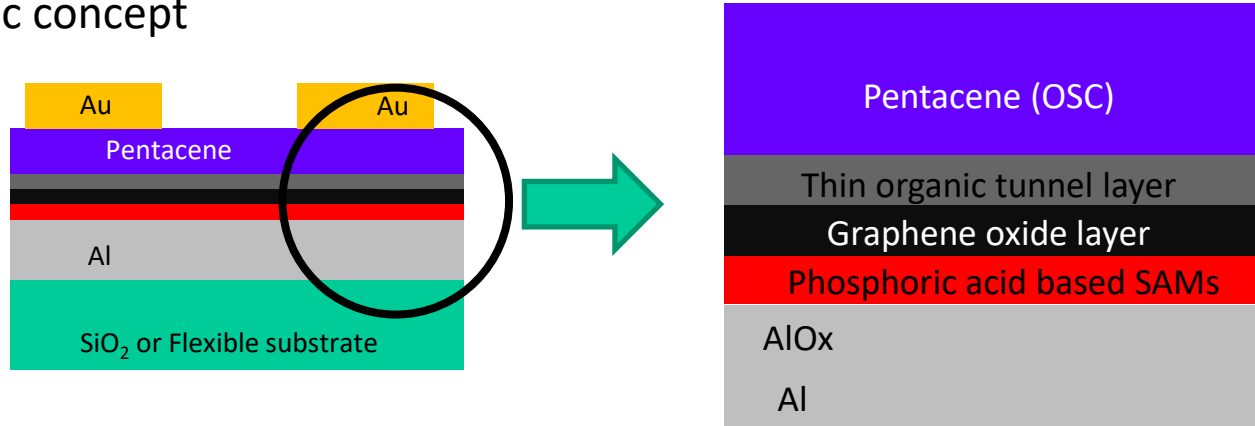
Organic memory transistors **do not need such a high post annealing**, hence GO is more useful as a charge trap layer in organic memory transistors.

One more advantage of GO is that it is **solution-processable (spin-coating) and ink-jet printable**, so it is compatible with memory storage systems based on flexible organic electronics.

GO based Low Voltage Organic Memory Transistors

- Graphene oxide + Hybrid gate dielectric(AlO_x +SAMs)

Basic concept



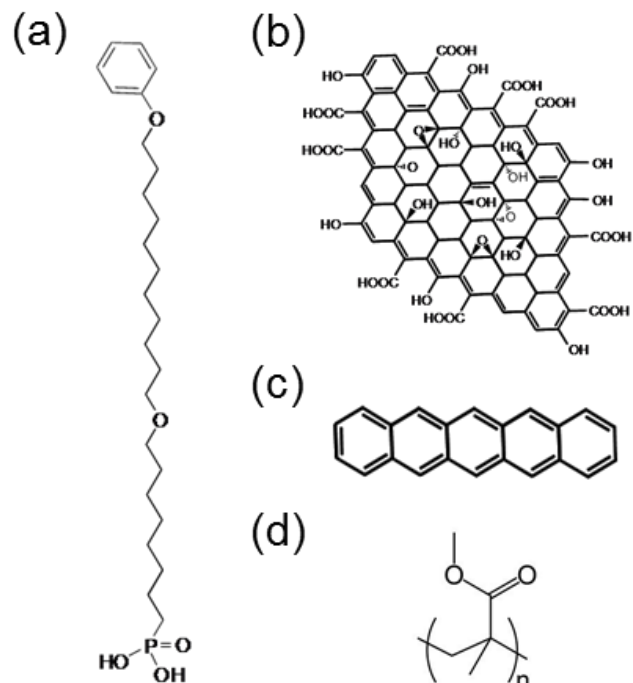
In our previous research, We clearly showed that graphene oxide is one of the charge trap layers for high performance organic memory transistors.

Fabrication process issue

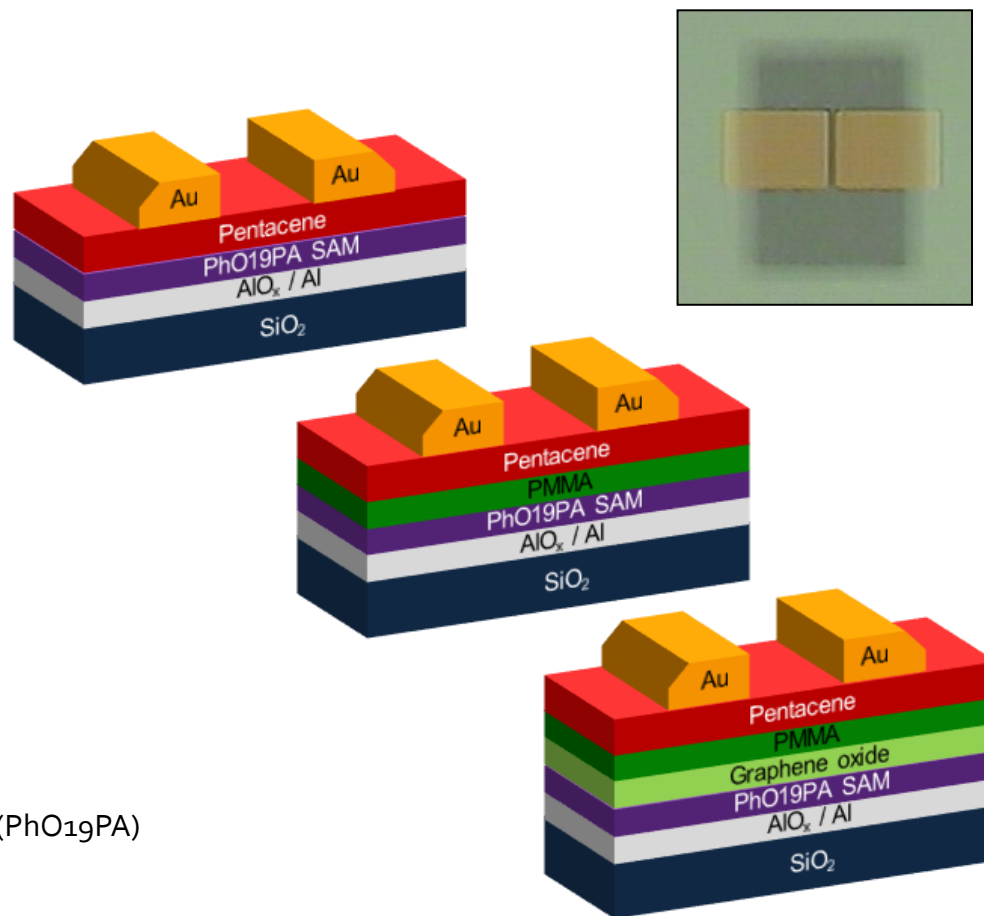
- Control of breakdown voltage of hybrid gate dielectrics
- Formation of SAMs on AlO_x
- Spin coating of graphene oxide on SAMs layer uniformly
- Materials selection and thickness control of organic tunnel layer

GO based Low Voltage Organic Memory Transistors

- Graphene oxide + Hybrid gate dielectric(AlO_x +SAMs)

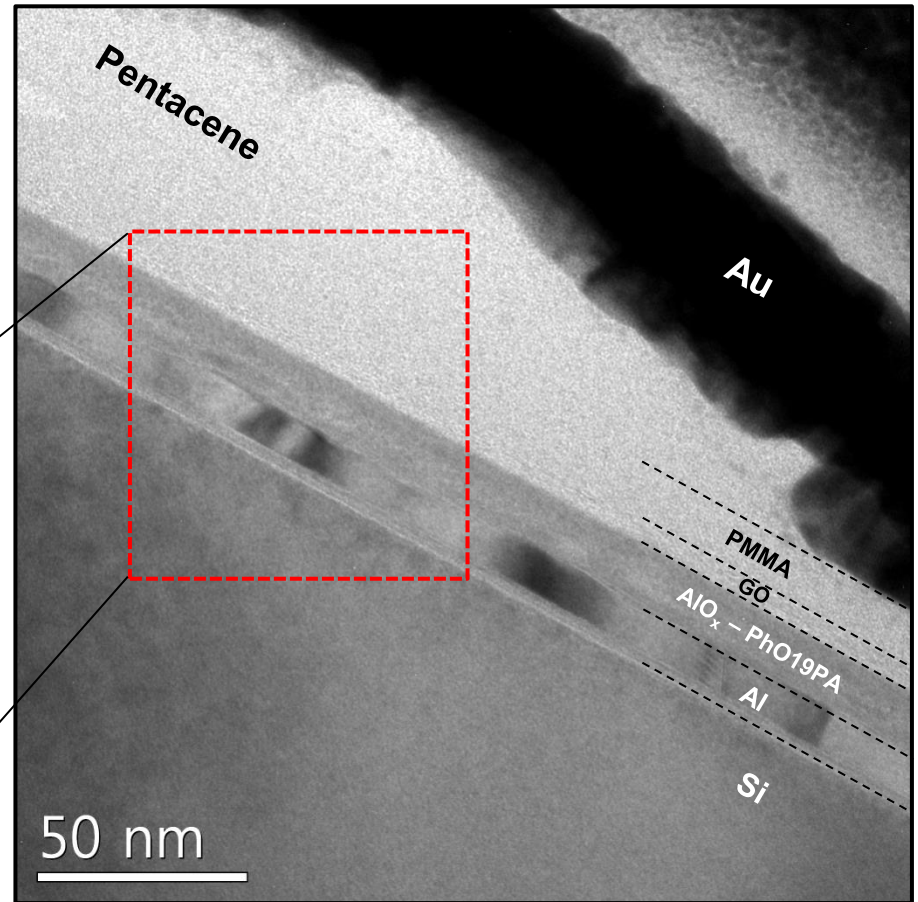
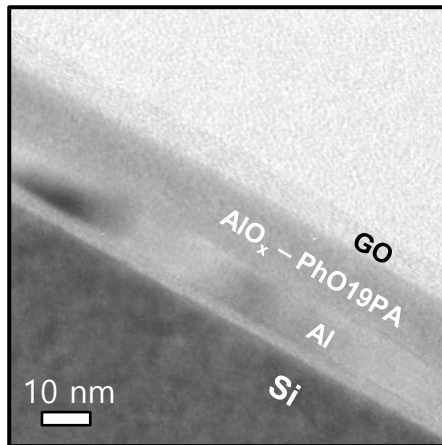
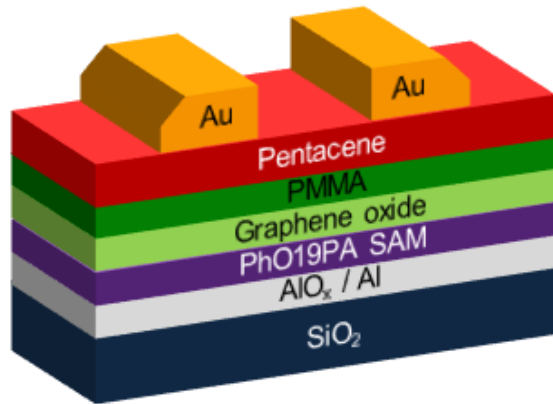


- (a) [8-(11-phenoxy-undecyloxy)-octyl]phosphonic acid (PhO19PA)
 (b) Graphene oxide
 (c) Pentacene
 (d) PMMA



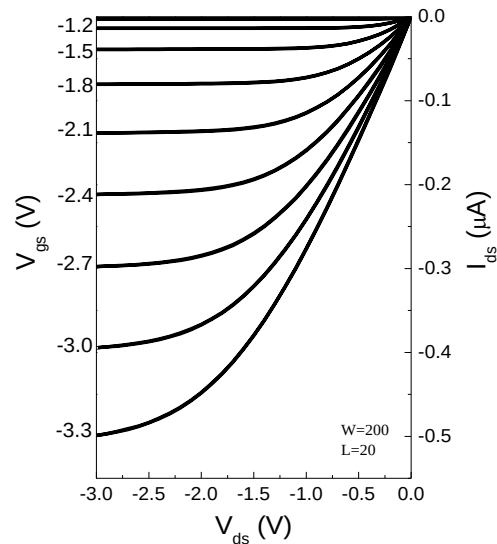
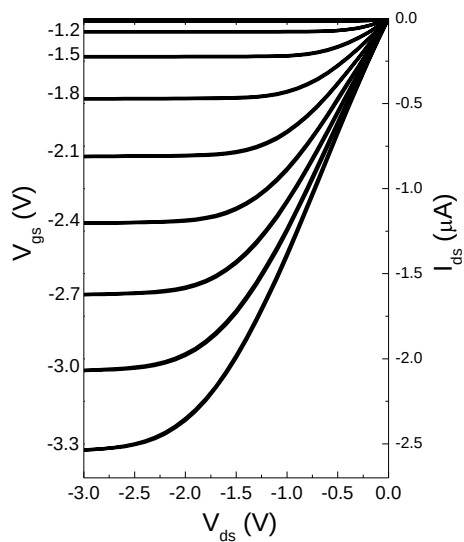
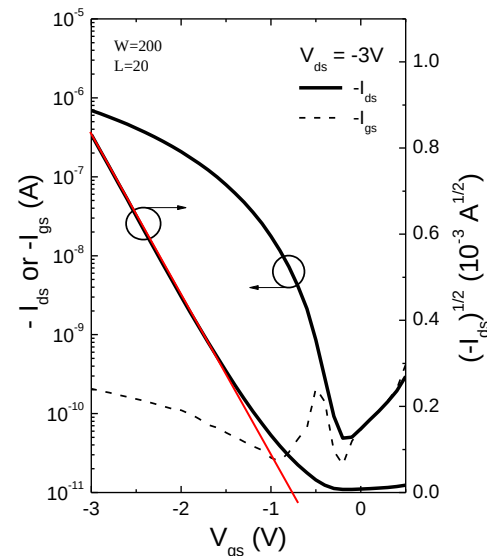
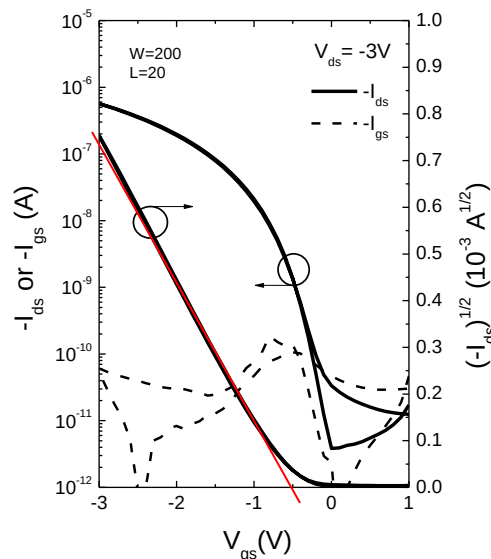
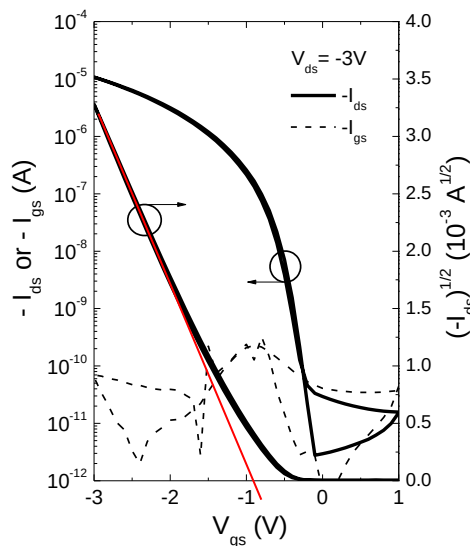
GO based Low Voltage Organic Memory Transistors

- Cross-sectional TEM image



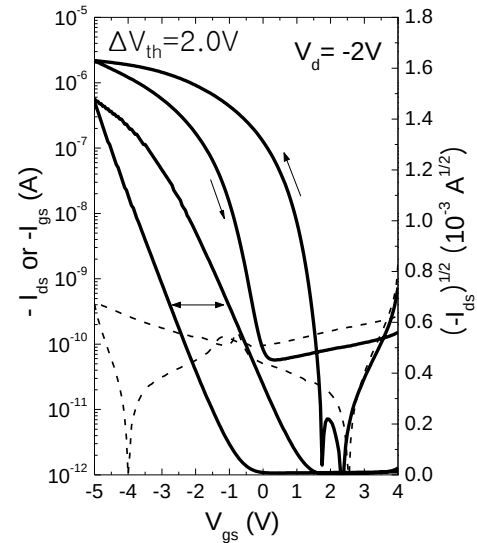
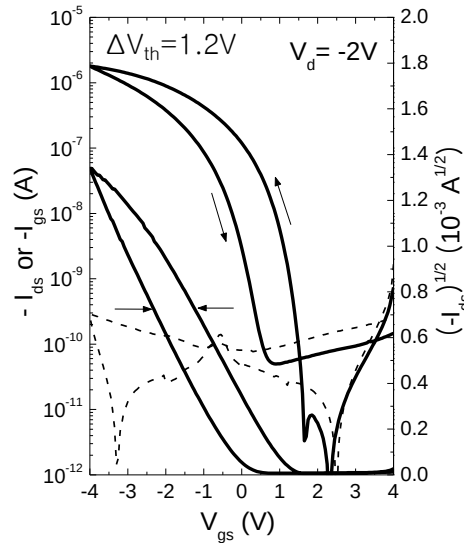
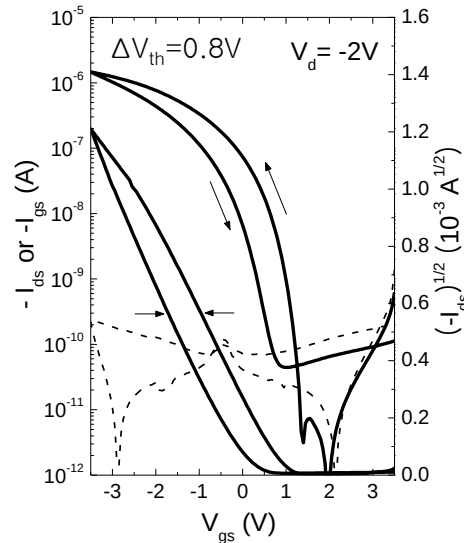
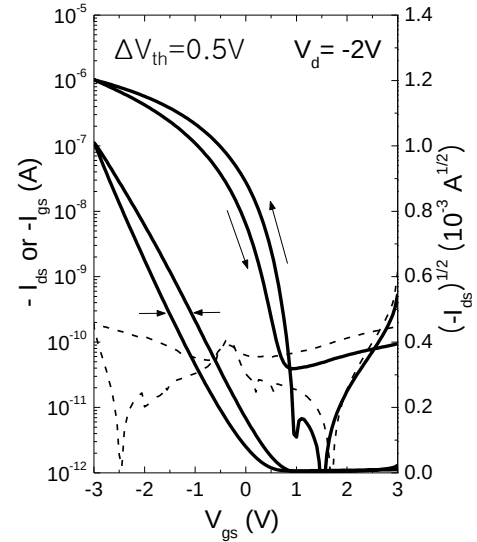
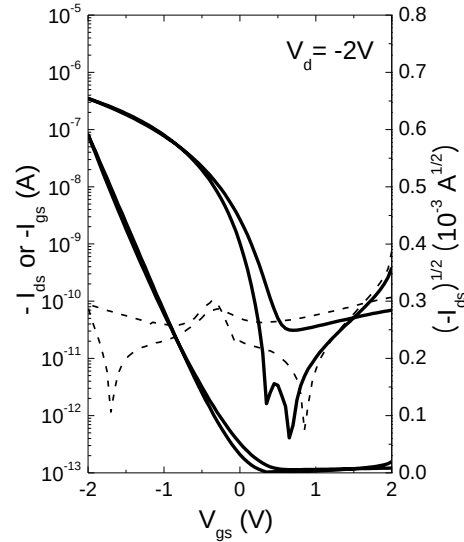
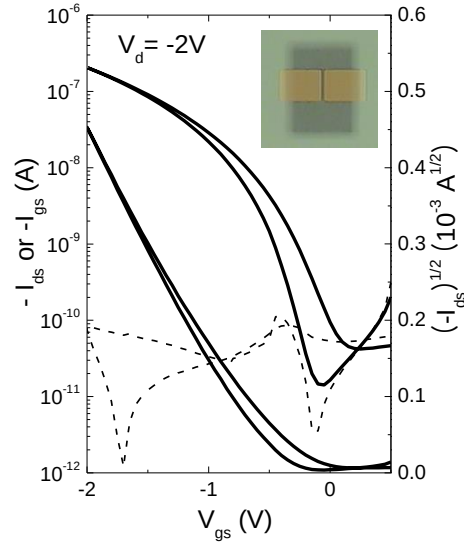
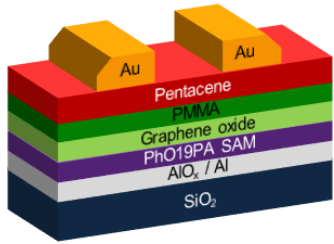
GO based Low Voltage Organic Memory Transistors

- Transfer and output characteristics



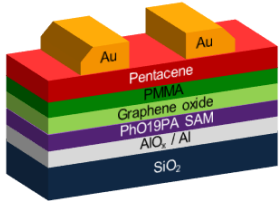
GO based Low Voltage Organic Memory Transistors

- Sweep Hysteresis



GO based Low Voltage Organic Memory Transistors

- Calculation of stored charges on Graphene oxide



The amount of the trapped charges at the graphene oxide layer was calculated

$$\Delta V_{th} = -d_i Q / \epsilon_i = -Q / C_i$$

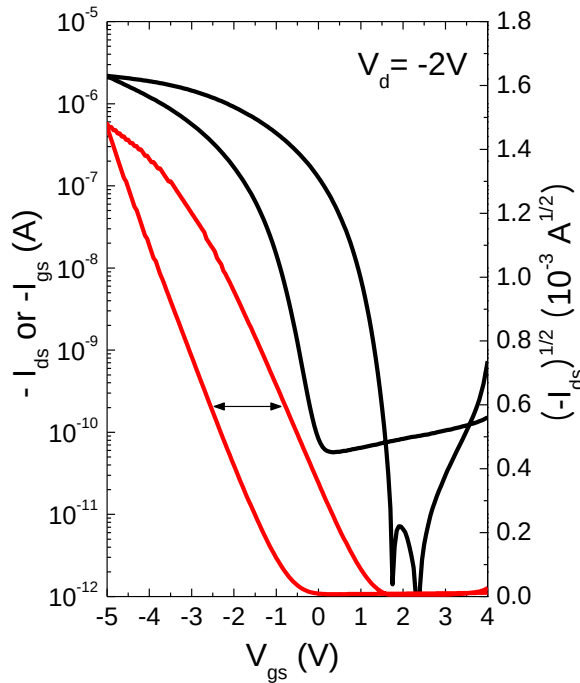
ΔV_{th} : the hysteresis window of memory transistor

Q : the trapped charge

C_i : the total capacitance of the gate dielectrics

Total amount of charge on thick graphene oxide (9nm)
 $\sim 2.9 \times 10^{12} \text{ cm}^{-2}$

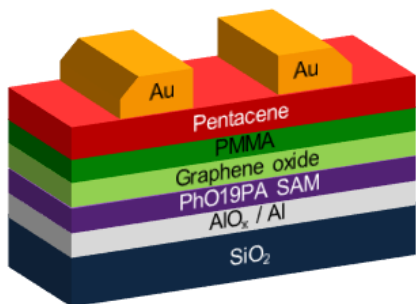
From $\Delta V_{th} = 2.0\text{V}$ and $C_i = 233 \text{ nF/cm}^2$.



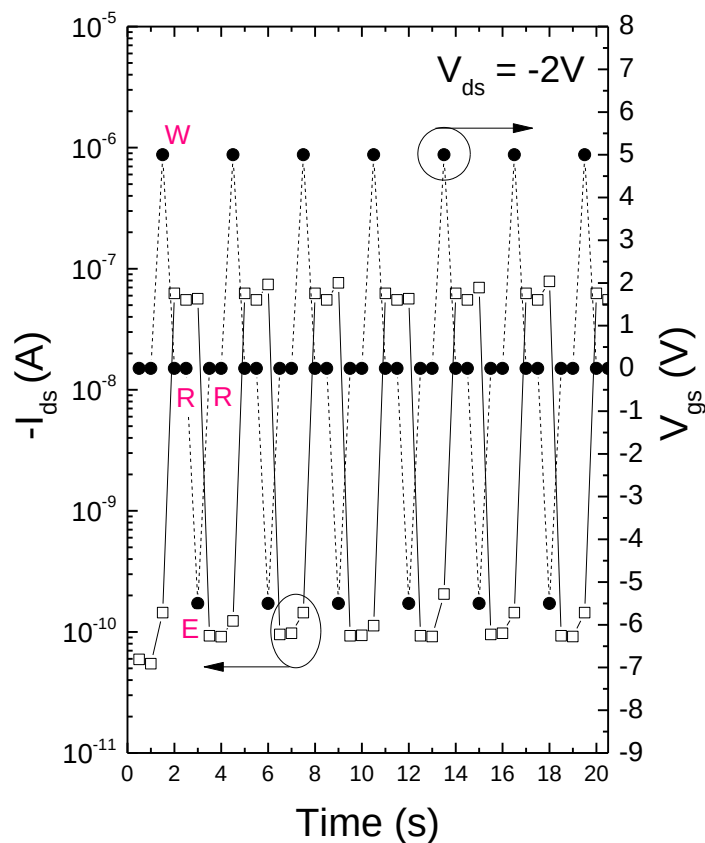
Monolayer of graphene oxide sheet has trap density of $3.22 \times 10^{11} \text{ cm}^{-2}$

GO based Low Voltage Organic Memory Transistors

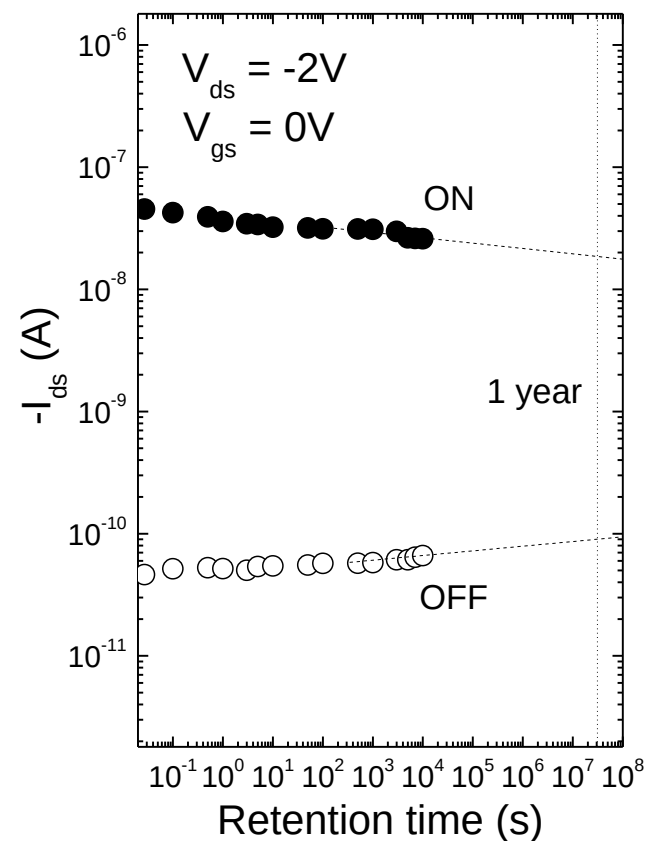
- Device performances



WRER Test

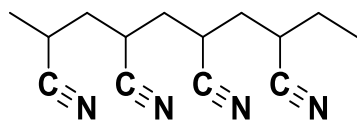
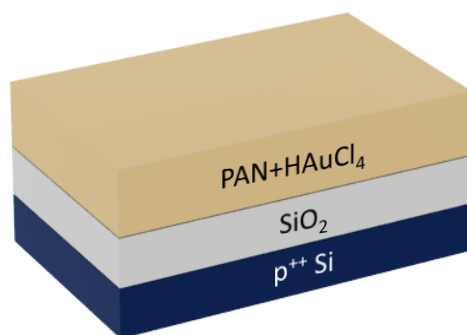


Data Retention



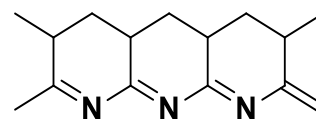
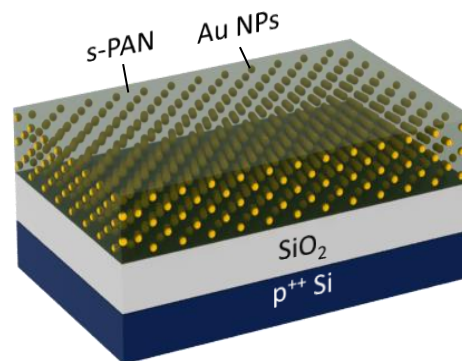
Organic Memory Transistors with One step synthesized Au NPs

- One step synthesis of Au nanoparticle-cyclized polyacrylonitrile composite films



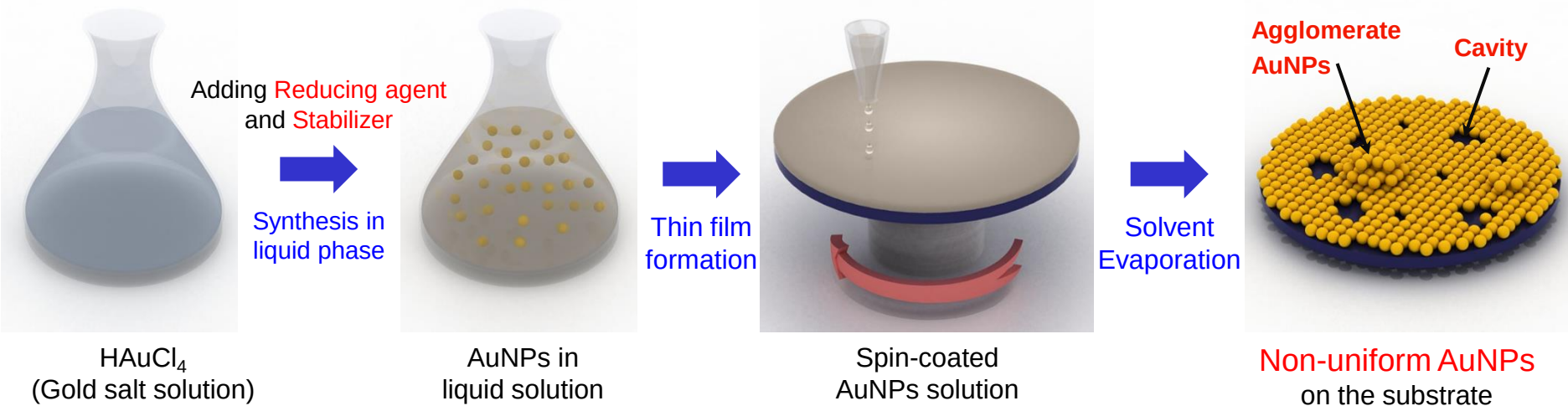
Polyacrylonitrile (PAN)

Stabilization
270°C



Cyclized PAN (cPAN)

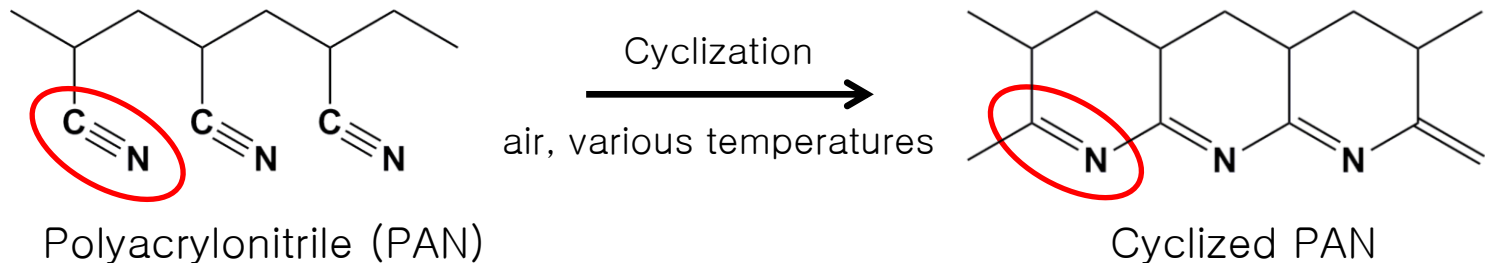
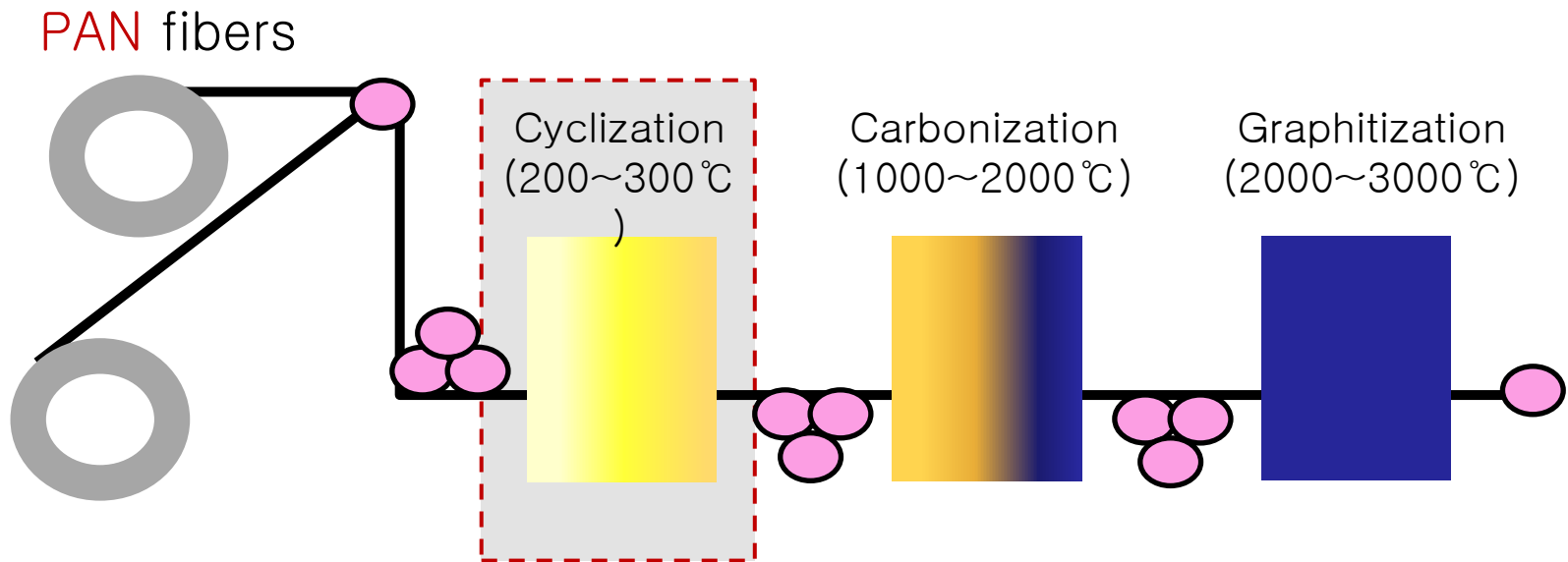
Conventional processes of Au NPs in device application



- AuNPs by a bottom-up method generally involves the chemical reduction of gold ions in a liquid phase with reducing agents and stabilizers.
- For actual device applications, **additional thin film formation** is essential after nanoparticle synthesis in liquid.
- **Problem** : This intricate process causes **agglomeration**, **deformation** of nanoparticles, and **damage to an organic underlayer** by interacting with the solvent or an additive, such as the reducing agent and the nanoparticle stabilizer, and causes a **non-uniform dispersion** in the matrix.
- For the NVM application, **electrically isolated states** of AuNPs are preferred.

Cyclization of Polyacrylonitrile (PAN)

Conventional Carbon fiber process



converts from the nitrile group ($-\text{C}\equiv\text{N}$) into a ladder structure ($-\text{C}=\text{N}$)

Fiber $\Rightarrow$ Film

?

- Fabrication Process

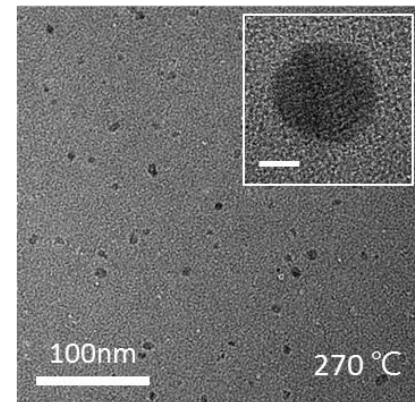
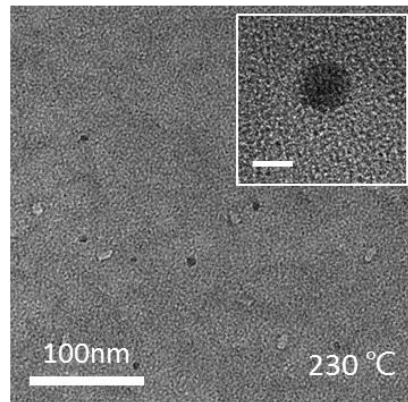
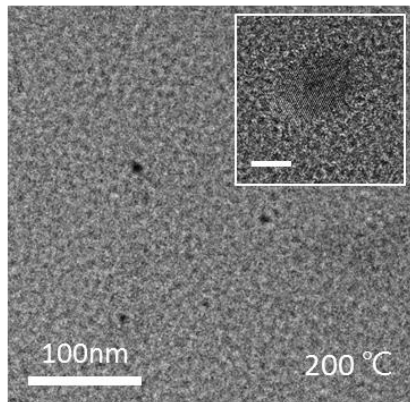
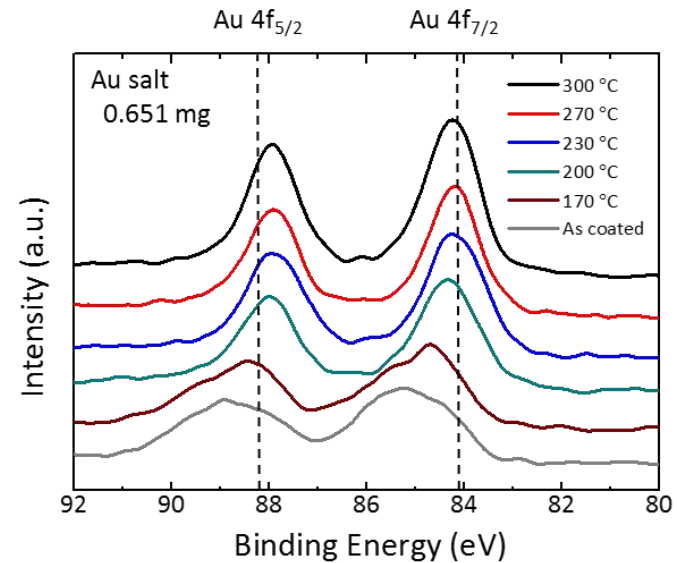
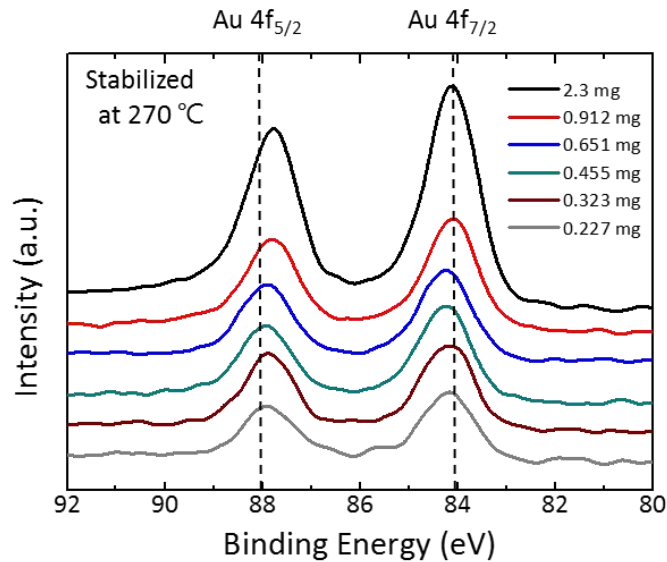


*Spin-coating was performed under 500 rpm for 5 sec/4000 rpm for 90 sec

Constant Ration	Cyclization Temp.	Constant temperature	HAuCl ₄ Ration (wt%)
<u>7:1</u> (PAN : 1ml)	As spin coating	Cyclization at <u>270 °C</u>	2:1
	170 °C		5:1
	200 °C		7:1
	230 °C		10:1
	270 °C		15:1
	300 °C		20:1

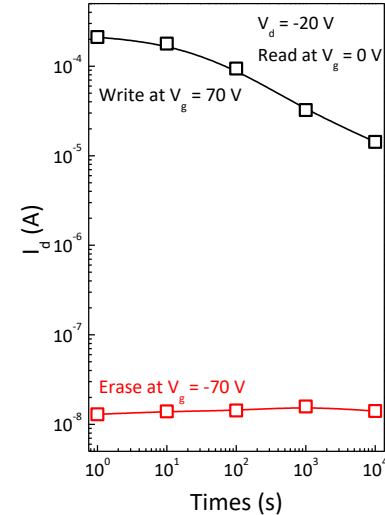
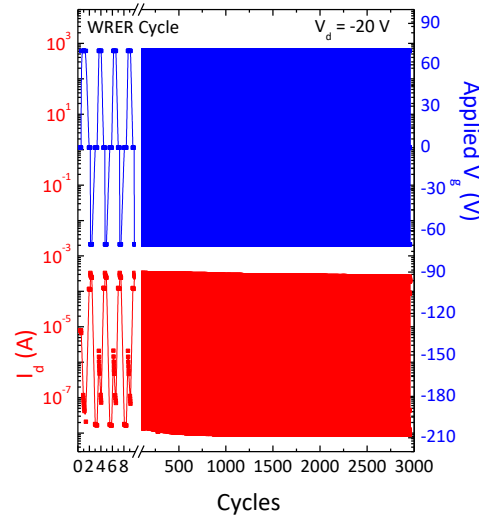
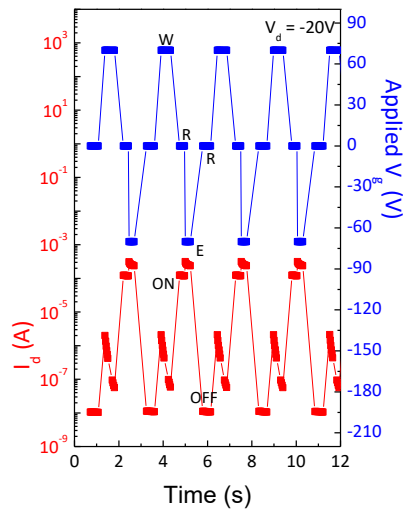
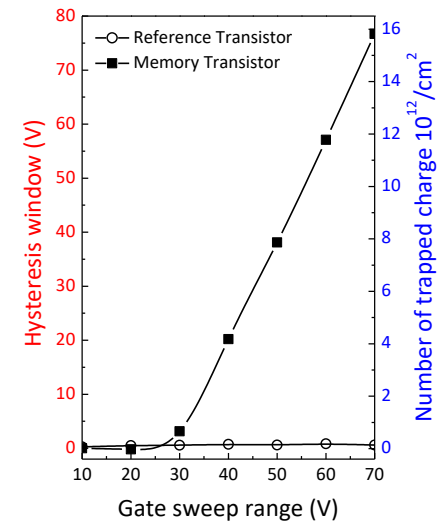
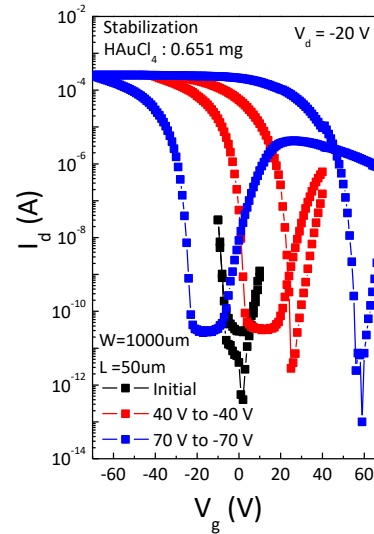
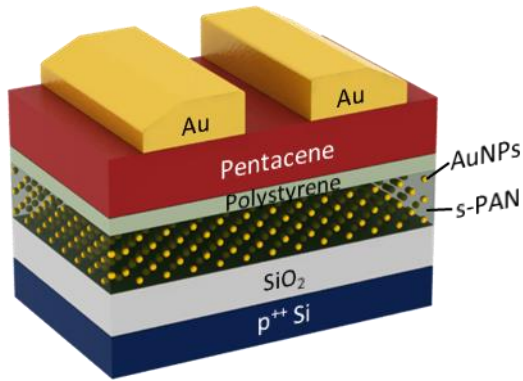
Organic Memory Transistors with One step synthesized Au NPs

- XPS & TEM analysis



Organic Memory Transistors with One step synthesized Au NPs

- Electrical characteristics



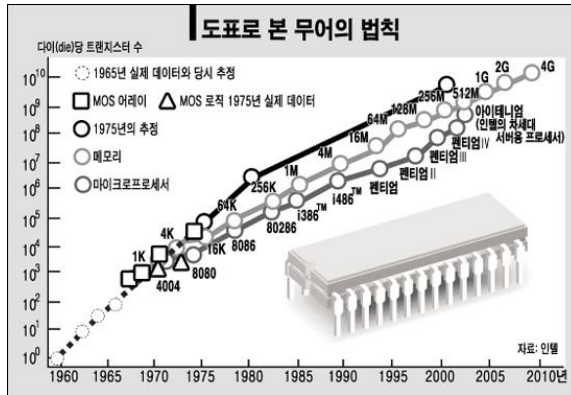
Neuromorphic Device

Ferroelectric Organic Neuromorphic Transistors (FONTs)

Why Neuromorphic Device?

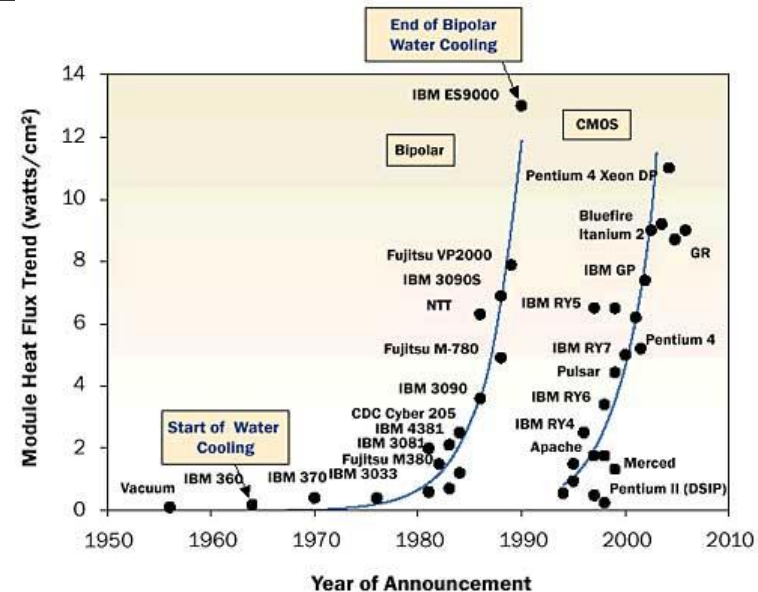
무어의 법칙 (1965) : 반도체의 집적회로의 성능이 18개월 마다 2배씩 증가한다!

황의 법칙 (2002): 메모리 집적도가 1년에 두배 씩 늘어난다 !

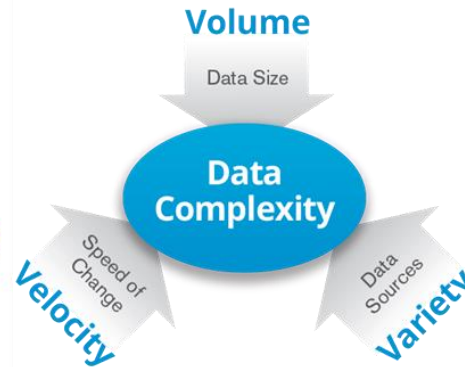


발열 문제?

Beyond CMOS → Neuromorphic chip



- ❖ BIG DATA, Display, Electronic products, Genetic data, etc



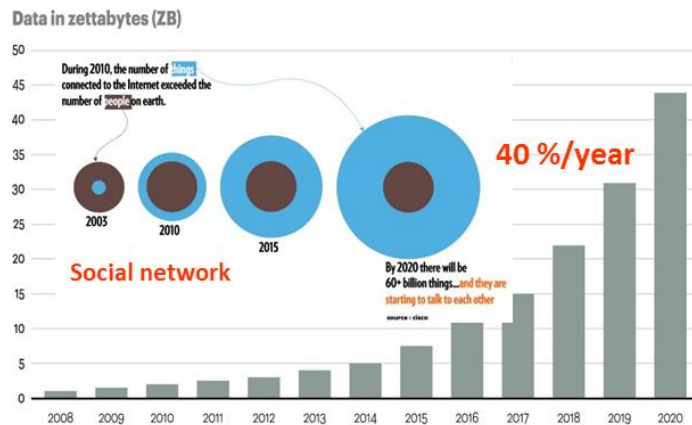
100 GB (for 4 k movie)
400 GB (for 8 k movie)



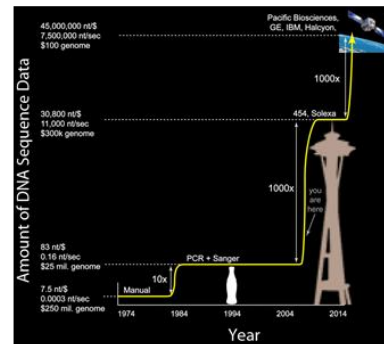
Google image

Figure 1

Data is growing at a 40 percent compound annual rate, reaching nearly 45 ZB by 2020

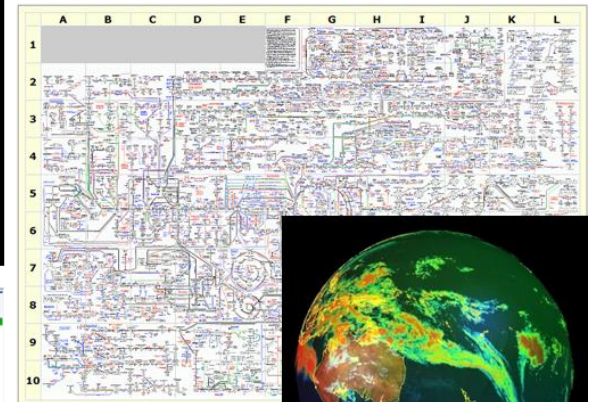


Source: Oracle, 2012

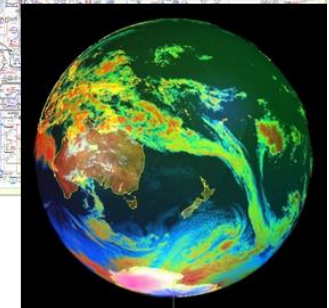


Genetic big data

Biochemical Pathways



Weather Big data



Heat, Energy Issues

❖ Storage, management, dissemination of organized information for business

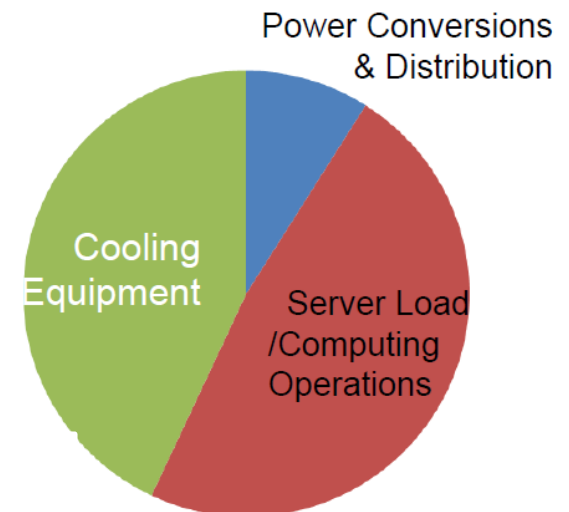
Google data center world wide



Google Data Center



Typical Data Center Energy End Use



Trends in Data Center Energy Use (USA)

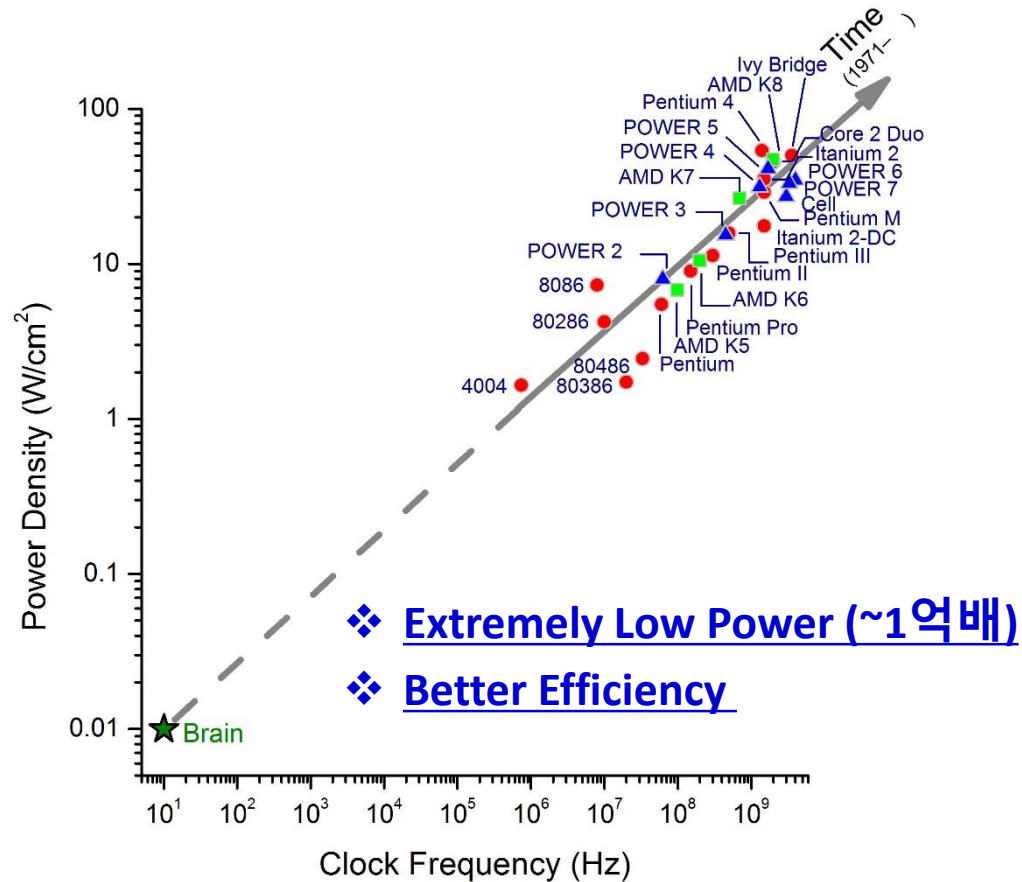
❖ ~ 100 billion kWh in 2011



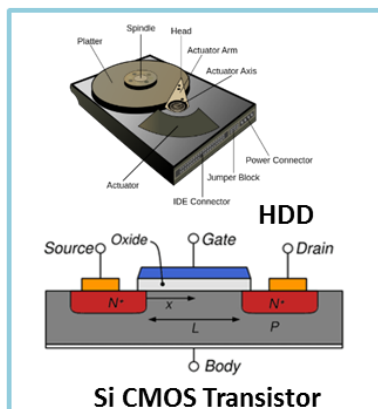
Total amount of energy use (Korea, 2013-2014)

❖ ~ 100 billion kWh per year

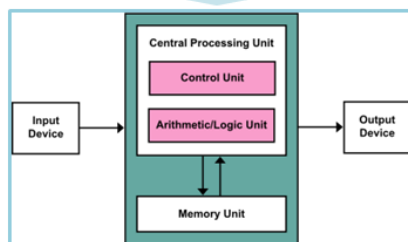
Why Brain mimicked Computer system?



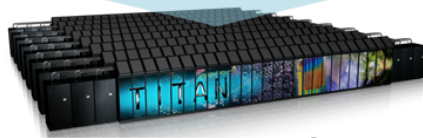
Human Brain vs. Super Computer



Basic components



Von Neumann architecture



Titan (404 m²)



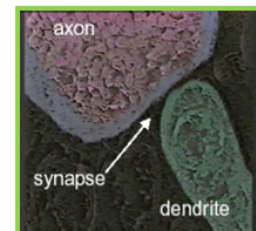
- 2 L
- 10^{11} neurons
- 10^{15} synapses
- 1-10 Hz (operational frequency)
- 20 W (power consumption)
- ~1 fJ (energy consumption)

1. Most efficiency computing system
2. Most complex system

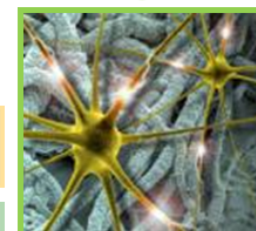
(Potential # of synapses network >> ???)

■ Super Computer (2nd ranked, Titan, 2012)'s CPU vs. Human Brain

Si CMOS Transistor (32 nm)	Basic device	Neuron (4 ~ 100 μ m) Synapse (~ 100 nm)
~ 200 x 10^{12} CMOS transistors ~ 19 K (CPU + GPU)	# of device	~ 10^{11} Neurons ~ 10^{15} Synapses
~20 x 10^{15} FLOPS	Computational power	> 40 x 10^{15} FLOPS
8.2×10^6 W	Power	20 W
Programmed, fast numerical cal., serial/parallel processing	Remarks	Learning, massively parallel signal processing



Synapses



Neuron

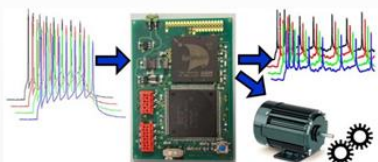


Human brain

Status of Current Research on Neuromorphic Devices

Proposal 영국 맨체스터 대학 SpiNNaker

- ▶ 다중채널 spiking input/output
- ▶ Simulates ~20,000 neurons
- ▶ 20 x 20 mm, 60 mW



SpiNNaker

Biologically
Inspired
Massively
Parallel
Architectures

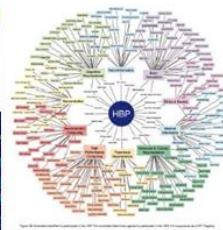
MANCHESTER
1824

Proposal 유럽의 Human Brain Project (1조 7천억)

- ▶ Neuroscience (뇌 시뮬레이션)
- ▶ 뇌 질환 관련 의료 분야
- ▶ 뇌 모사 인지 컴퓨팅



Human Brain Project



Unprecedented scale

This second generation chip is the culmination of almost a decade of research and development, and is a huge leap forward from the initial single-core hardware prototype developed in 2011.

	2011	2014
Programmable neurons	256	1 million
Programmable synapses	262,144	256 million
Neurosynaptic cores	1	4,096

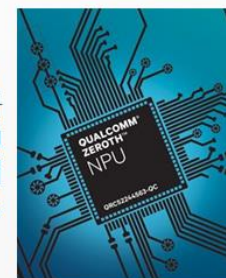
1/10th of a Watt powers the neurosynaptic chip's 256 million synapses... with the goal to simulate 1 trillion synapses using only 4 kW of energy

Proposal 기업 주도 성취 (미국)

- ▶ IBM TruNorth chip (2014), 2 억 5천만 개의 시냅스 (54 억개의 Tr.) → 보행자, 차량 구별 시연



- ▶ Qualcomm Zeroth Program
모바일 프로세스와 연결 가능한 NPU (뉴로시냅틱 HW) 개발 → 자율 주행 로봇 시연



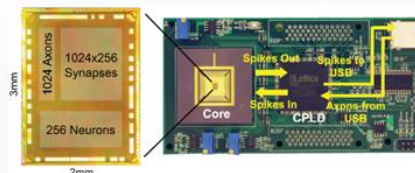
Proposal 미국 DARPA의 SyNAPSE 프로그램

- ▶ 뇌 모방형 칩 개발
- ▶ 뇌 모방형 아키텍처 설계
- ▶ 시스템 시뮬레이터 개발

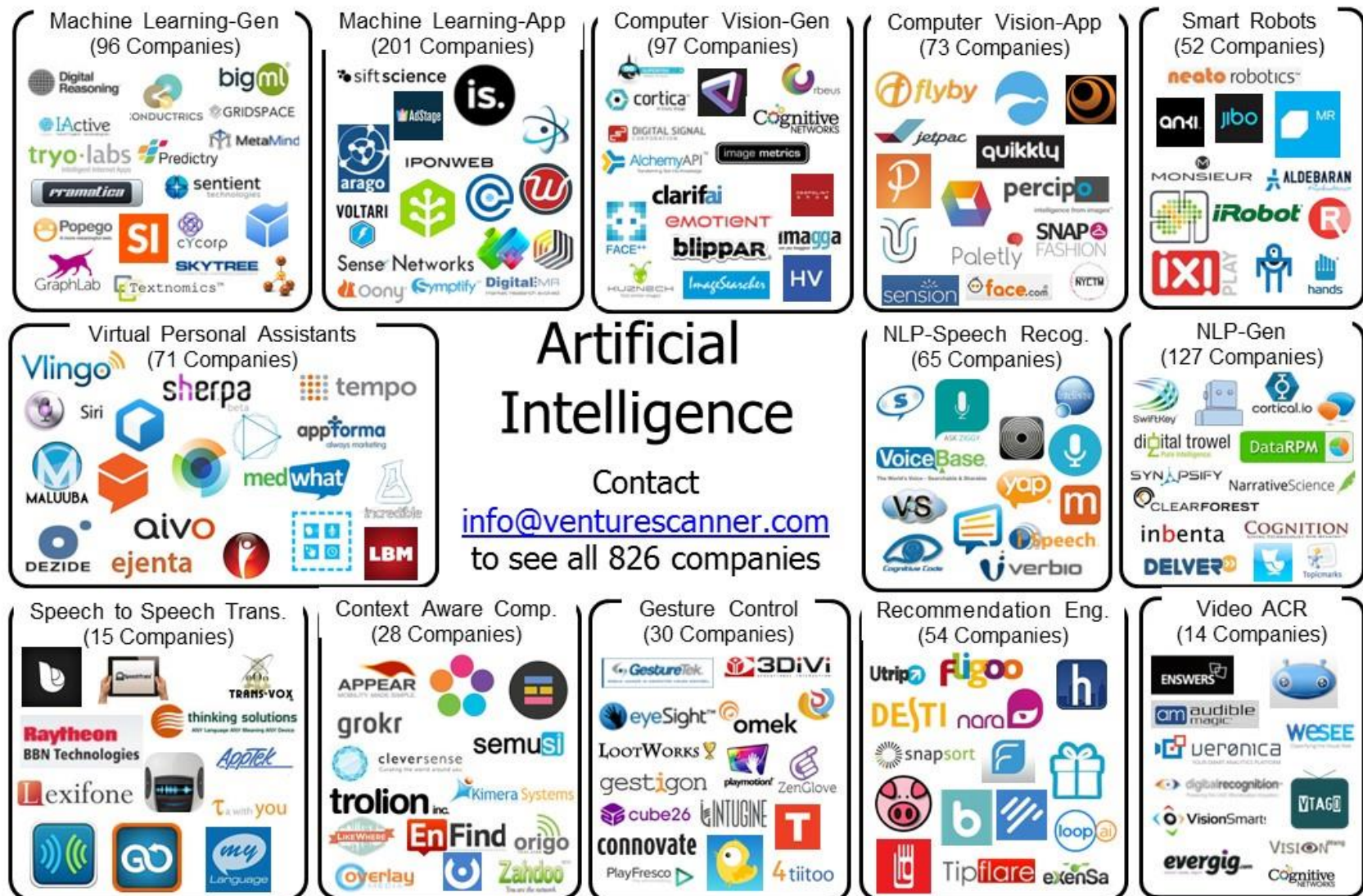
SyNAPSE

IBM

**HRL
LABORATORIES**



Status of Current Research on Neuromorphic Devices



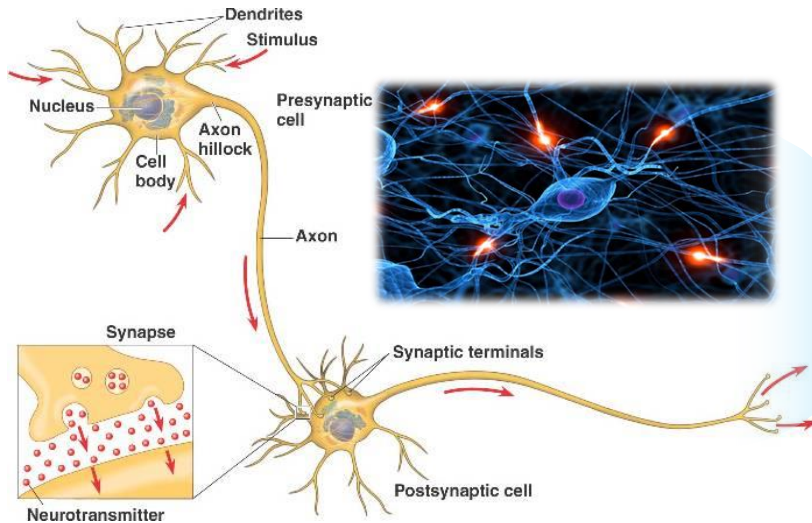
Artificial Intelligence

Contact

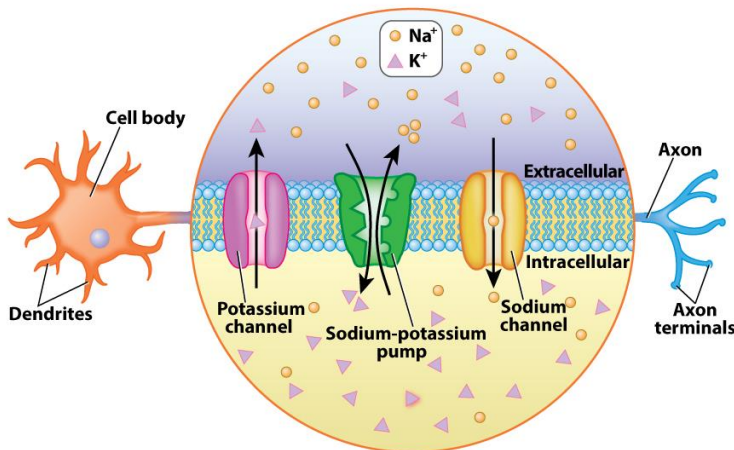
info@venturescanner.com
to see all 826 companies

Neuron

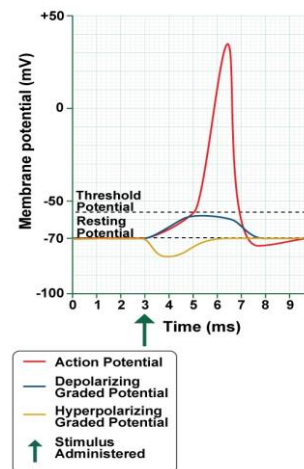
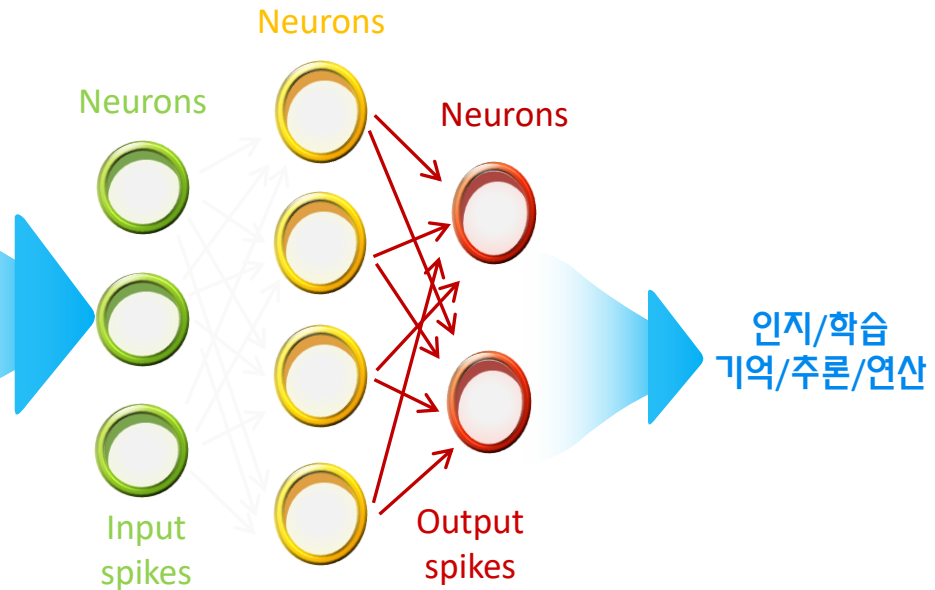
Neuron and synapse



~10³ 시냅스/뉴런



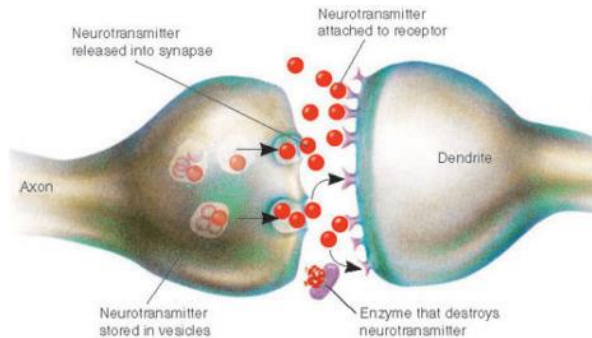
Parallel network



- Small changes in membrane potential (graded potentials) can be depolarizing or hyperpolarizing.
- A depolarizing potential that exceeds a threshold becomes an action potential.

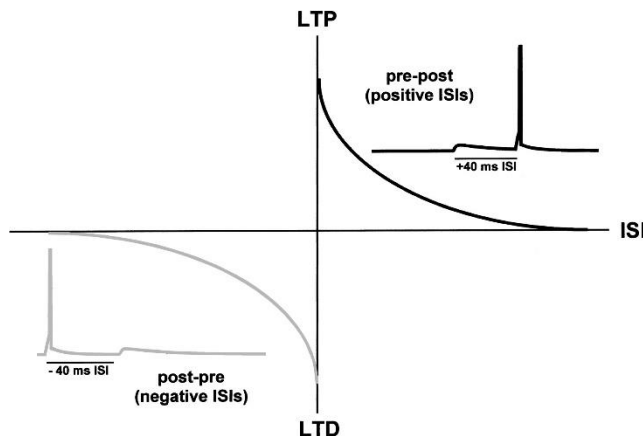
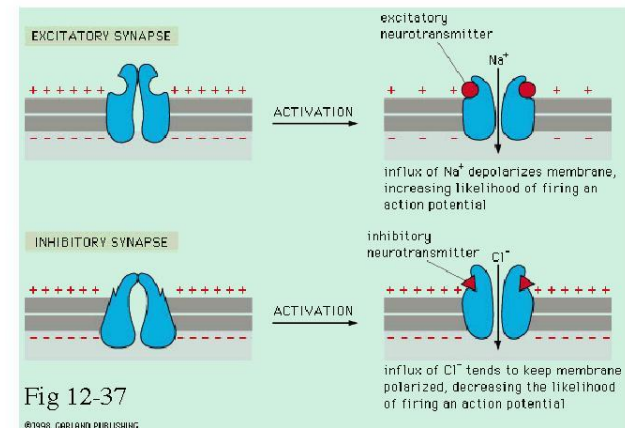
Synaptic Plasticity

Synaptic plasticity is the ability of synapses to strengthen or weaken over time, in response to increases or decreases in their activity. (기억, 학습, 연산, 추론과 관련된 기능)
Memory, learning, computation, reasoning



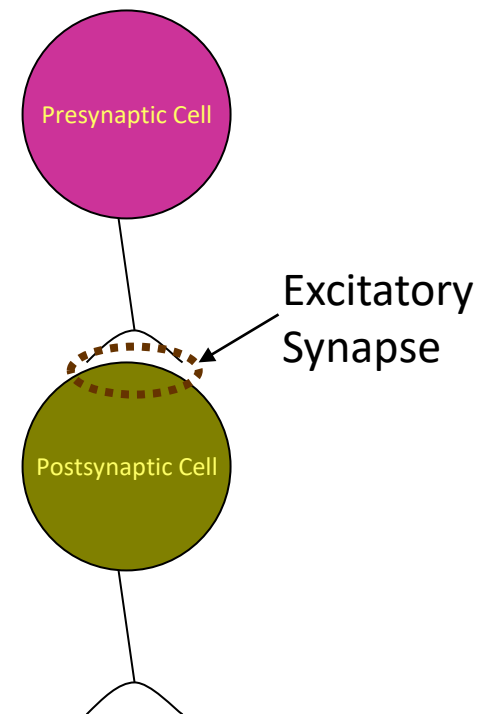
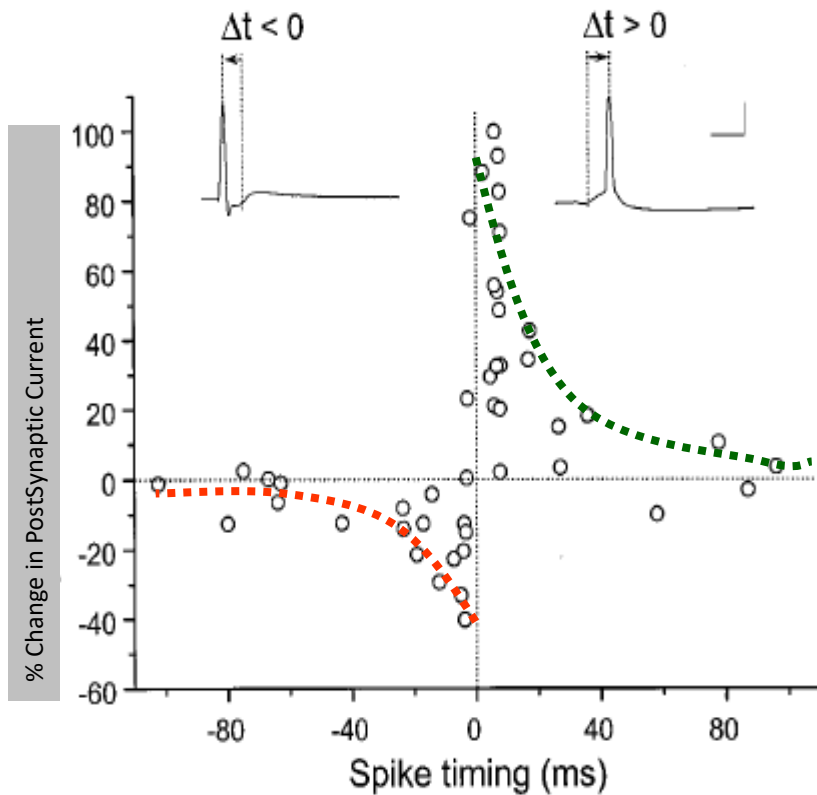
Hebb's Postulate: When an axon of cell A... excites cell B and repeatedly or persistently takes part in firing it, **some growth process or metabolic change takes place in one or both cells** so that A's efficiency as one of the cells firing B is increased.

Excitatory vs. Inhibitory Synapse



In standard Hebbian learning, **a synaptic weight is increased if presynaptic and postsynaptic neuron are 'simultaneously' active.** If neurons communicate by spikes, the concept of simultaneity implies the pre- and postsynaptic spikes occur within some time window. Theory predicts that **these time windows could have two phases corresponding to an increase (potentiation) or decrease (depression) of the synaptic weight depending on the relative timing of pre- and postsynaptic spike.** Such asymmetric learning rules with two phases have been found in recent experiments.

Spike Timing Dependent Plasticity (STDP)

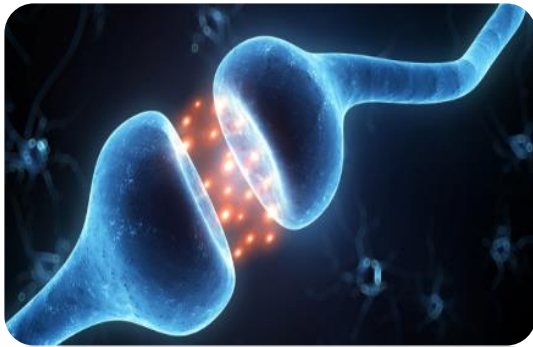


$$\Delta t = t_{\text{post}} - t_{\text{pre}}$$

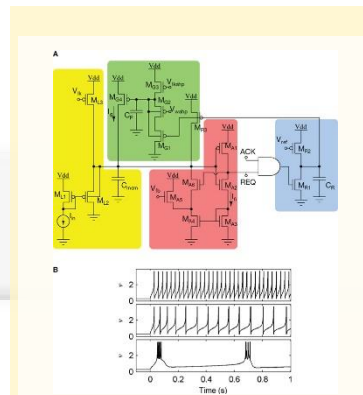
Mimicking Synaptic Device

- Long Term Potentiation (LTP), Long Term Depression (LTD) (장기 기억, 학습)
- STP, STD (for Short Term Memory)
- Spike Timing Dependent Plasticity (STDP)
- Ultralow power
- Ultrahigh density
- ...

■ Function of synapse

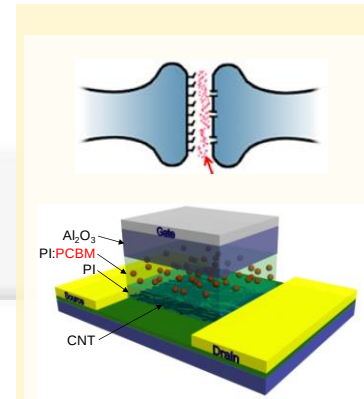


Analog Tr
neuromorphic circuit



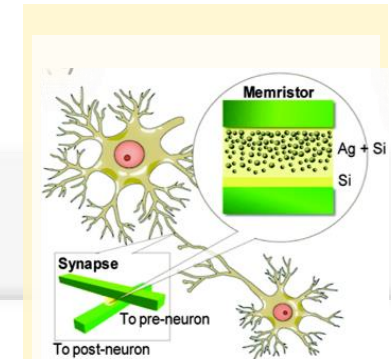
Front. Neurosci., (2011)

Floating-gate synaptic device



Small, (2013)

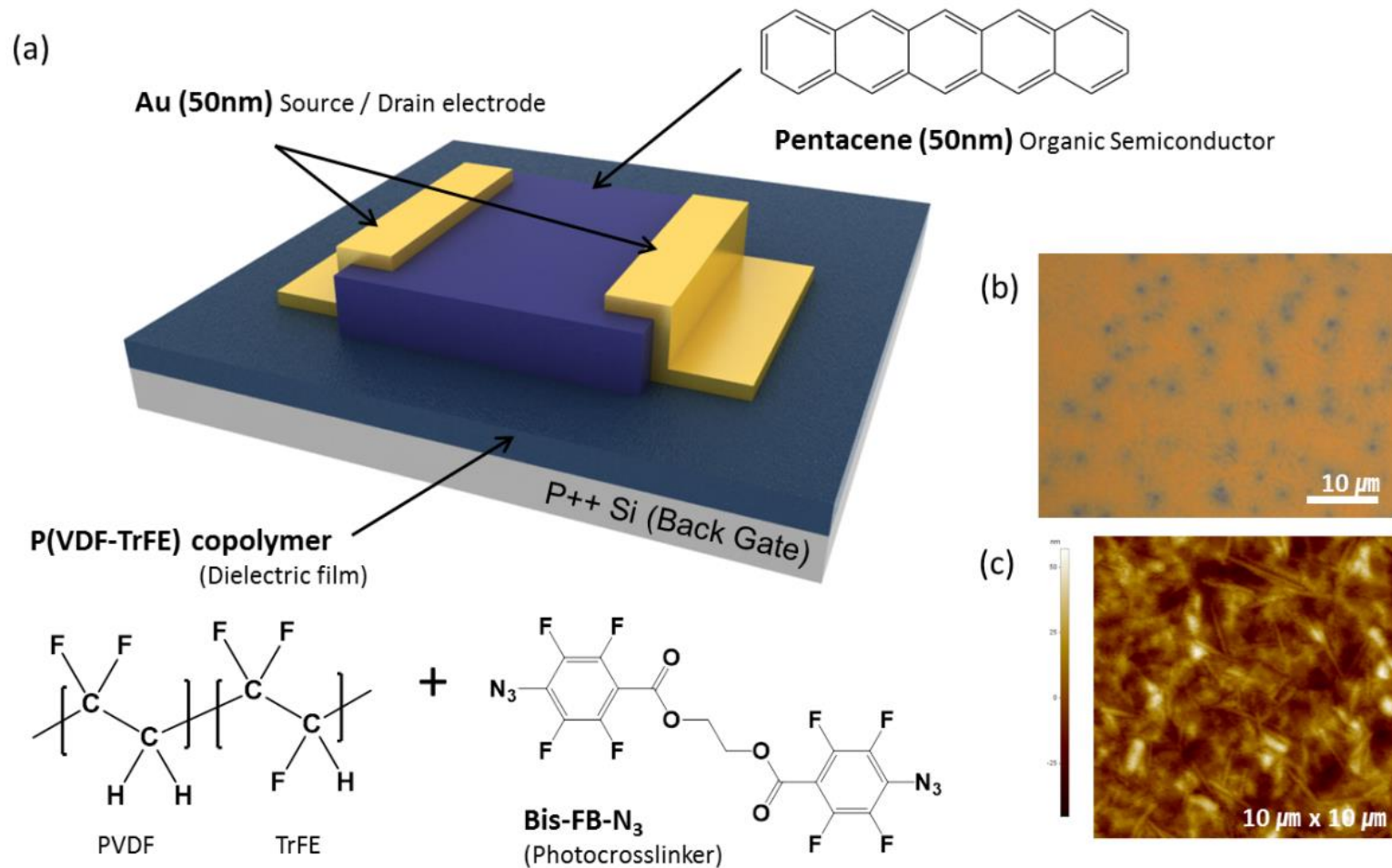
Resistive/memristor synaptic device



Nano Letters, (2010)

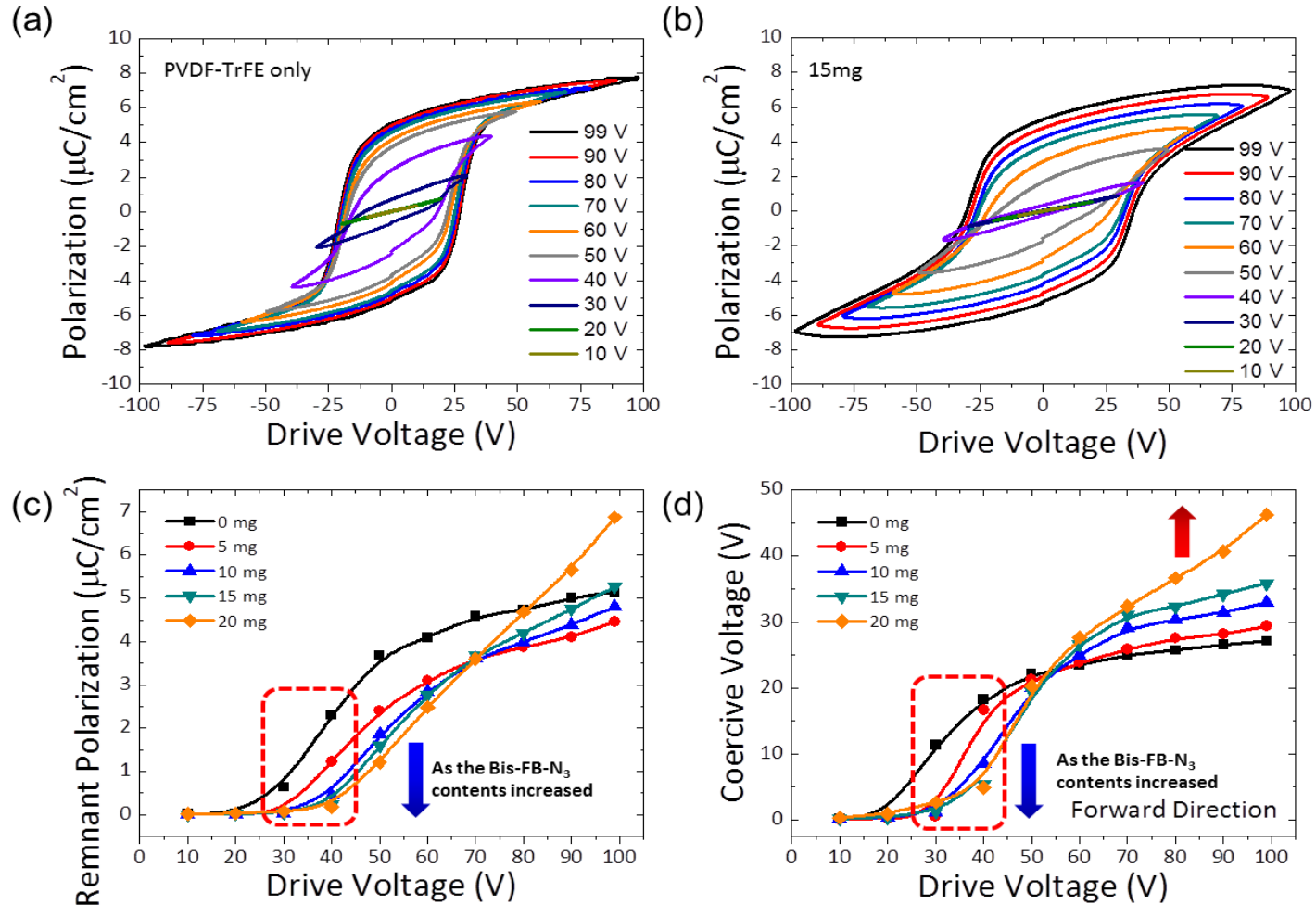
Control of ferroelectricity of P(VDF-TrFE)

- Device structure and materials



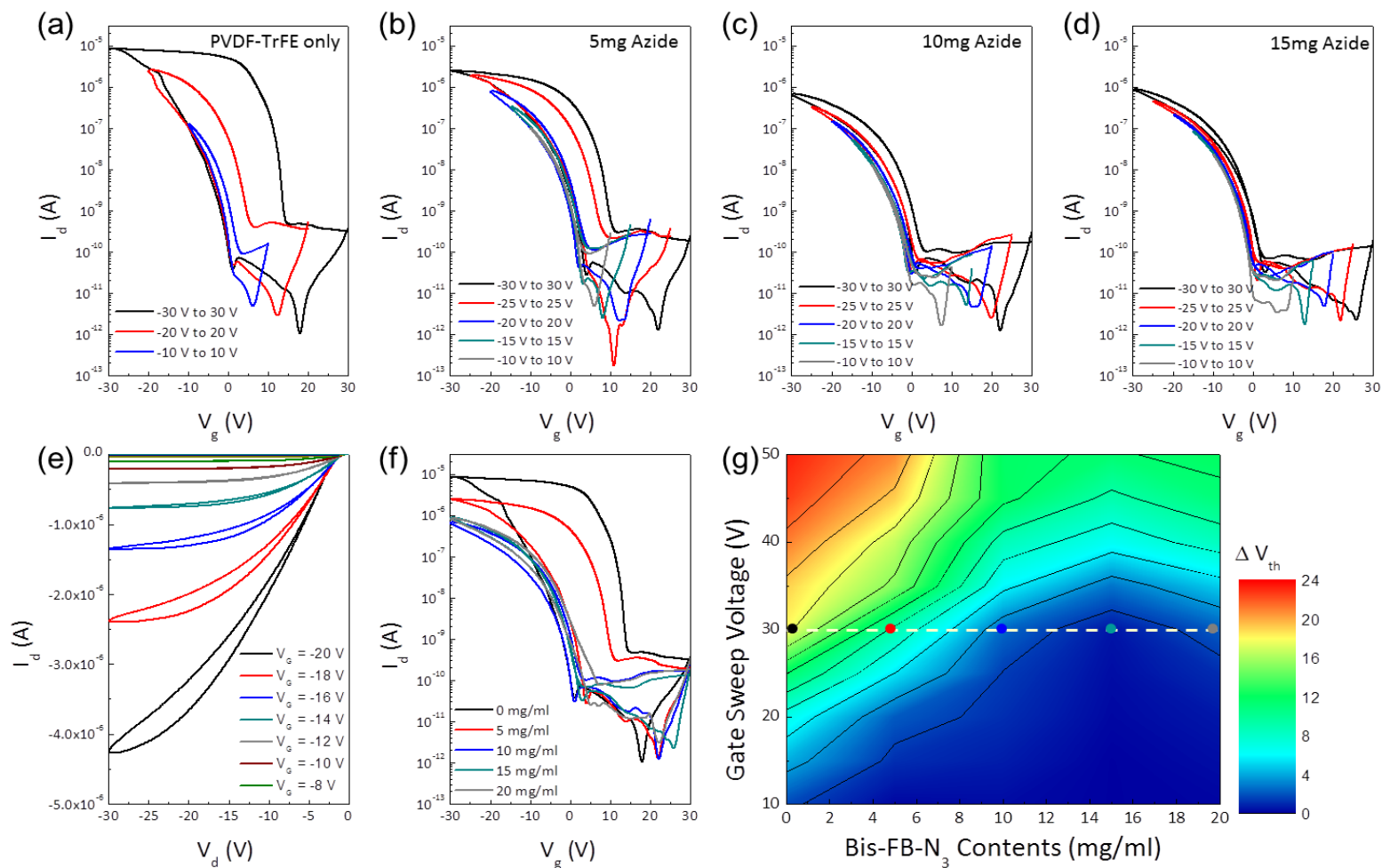
Control of ferroelectricity of P(VDF-TrFE)

- Polarization curve via contents of crosslinker

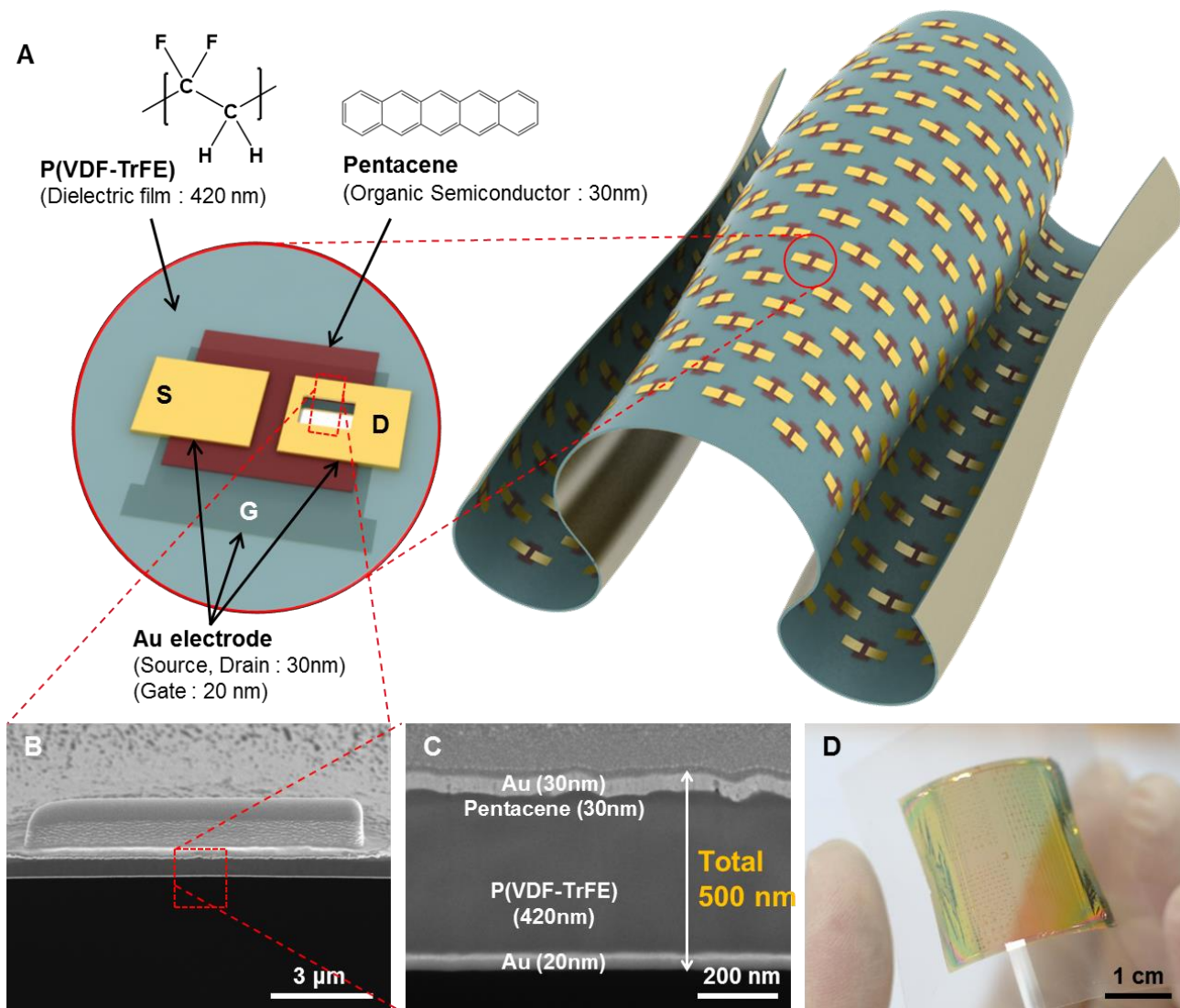


Control of ferroelectricity of P(VDF-TrFE)

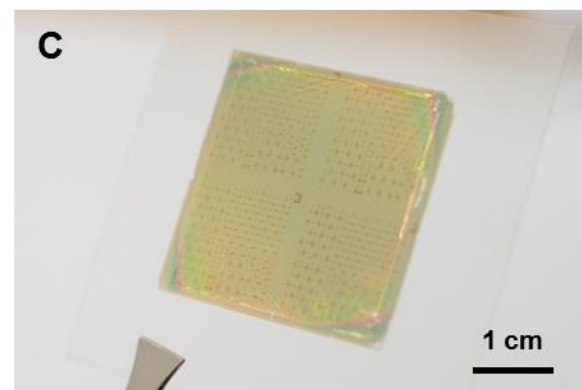
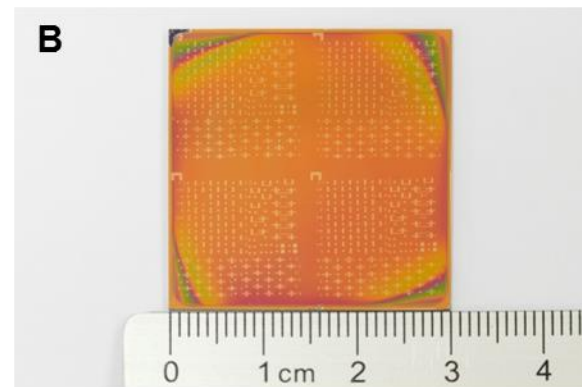
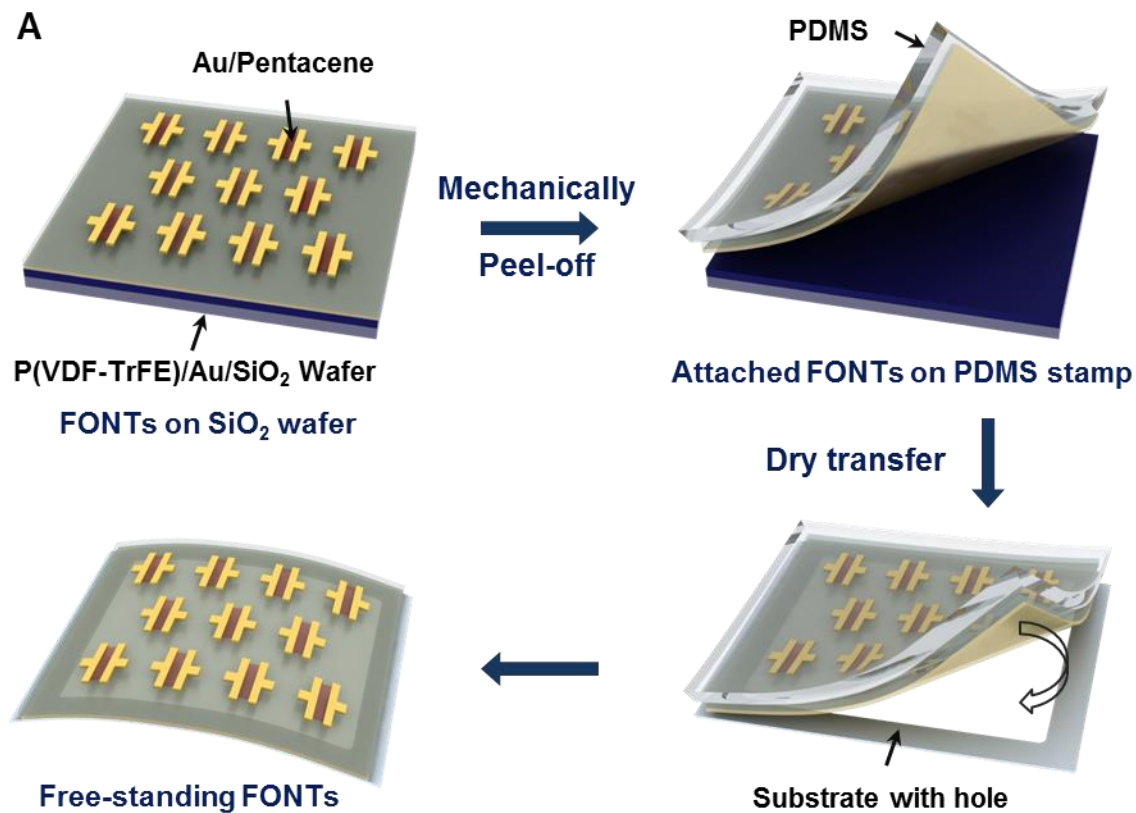
- Transfer curves of the ferroelectric transistors via contents of crosslinker



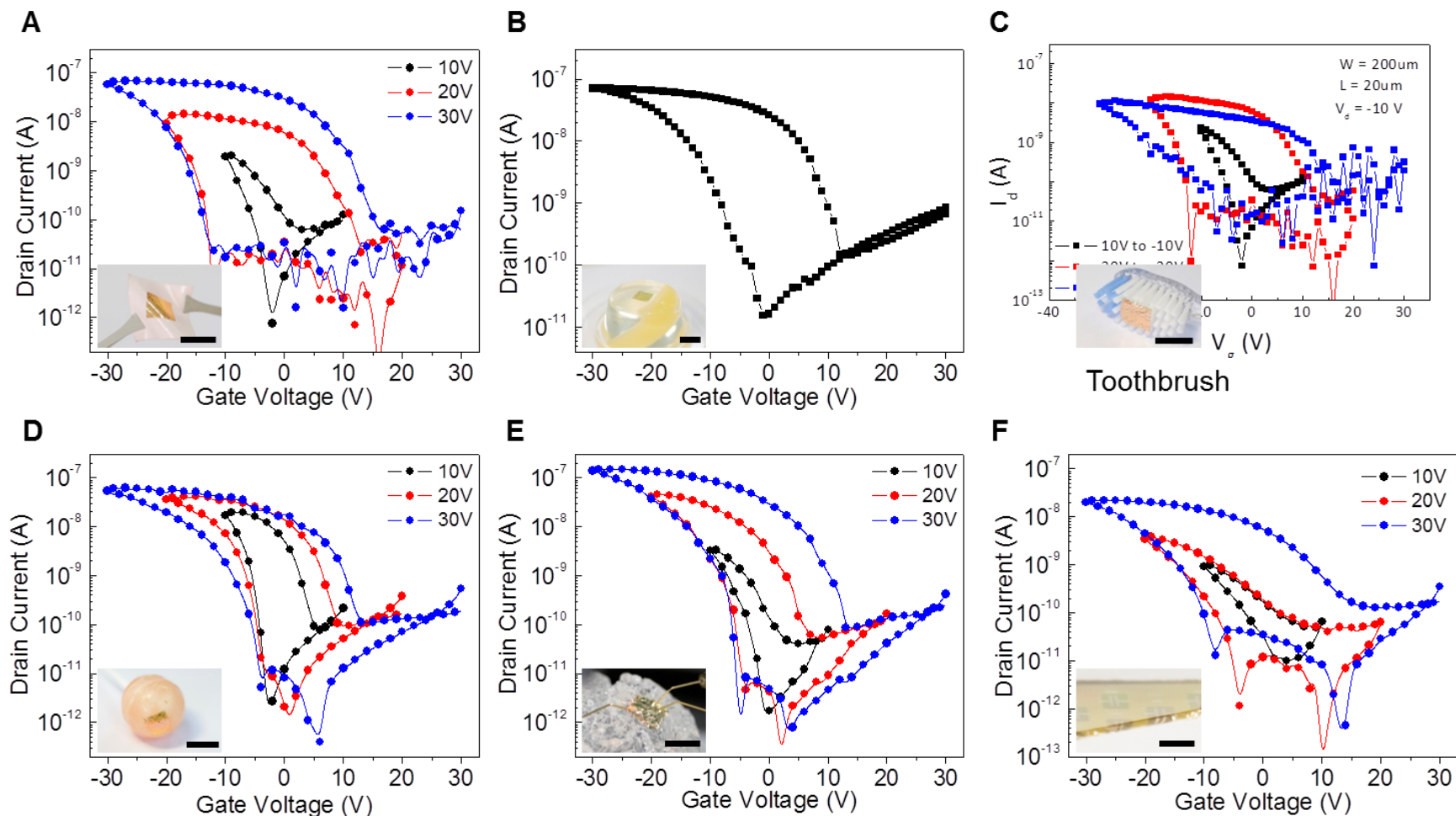
Ferroelectric organic neuromorphic transistors (FONTs)



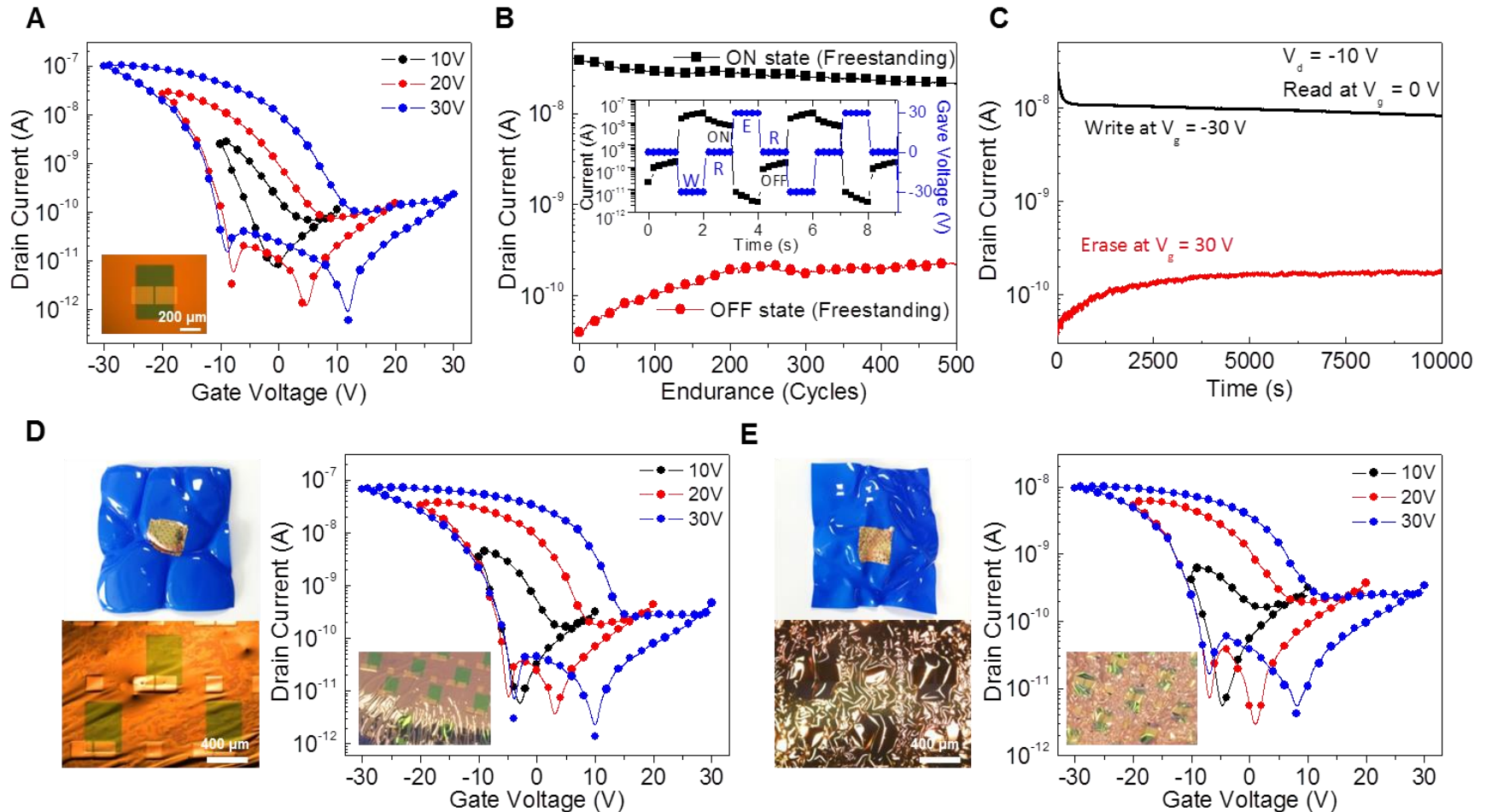
Ferroelectric organic neuromorphic transistors (FONTs)



Ferroelectric organic neuromorphic transistors (FONTs)

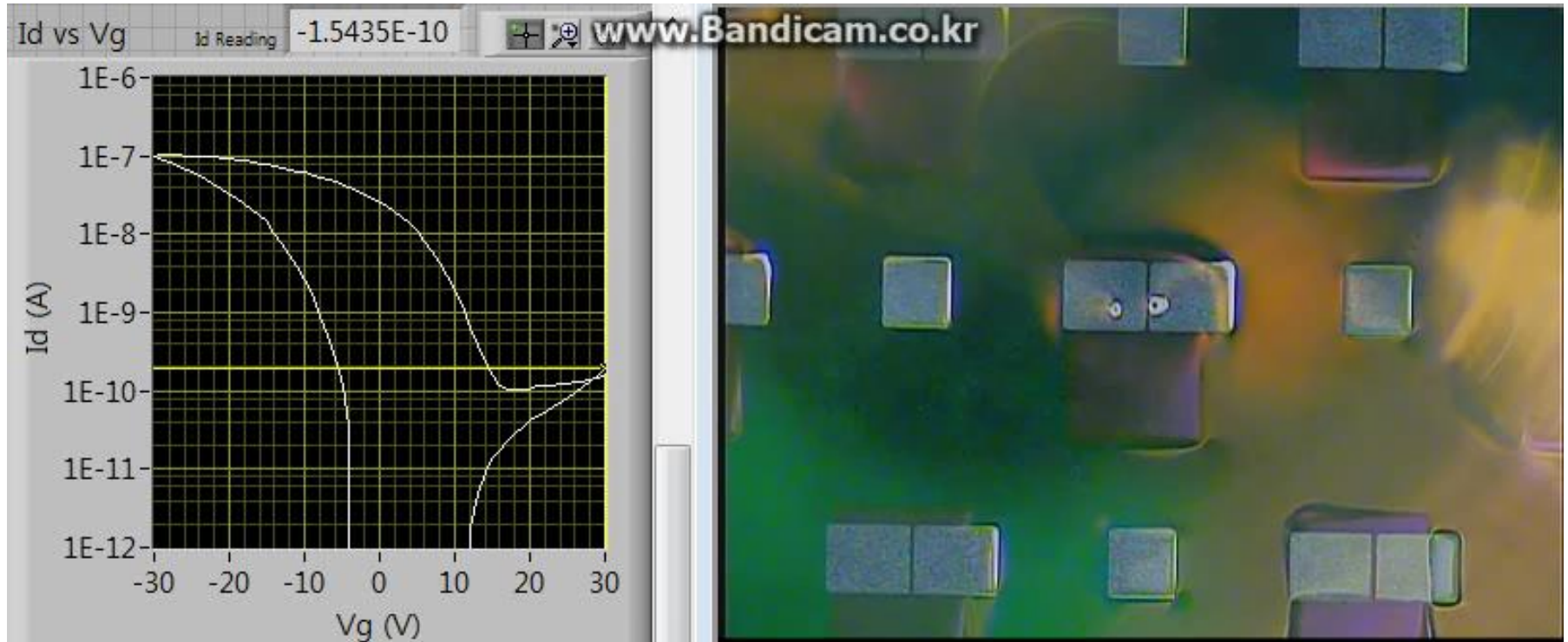


Ferroelectric organic neuromorphic transistors (FONTs)

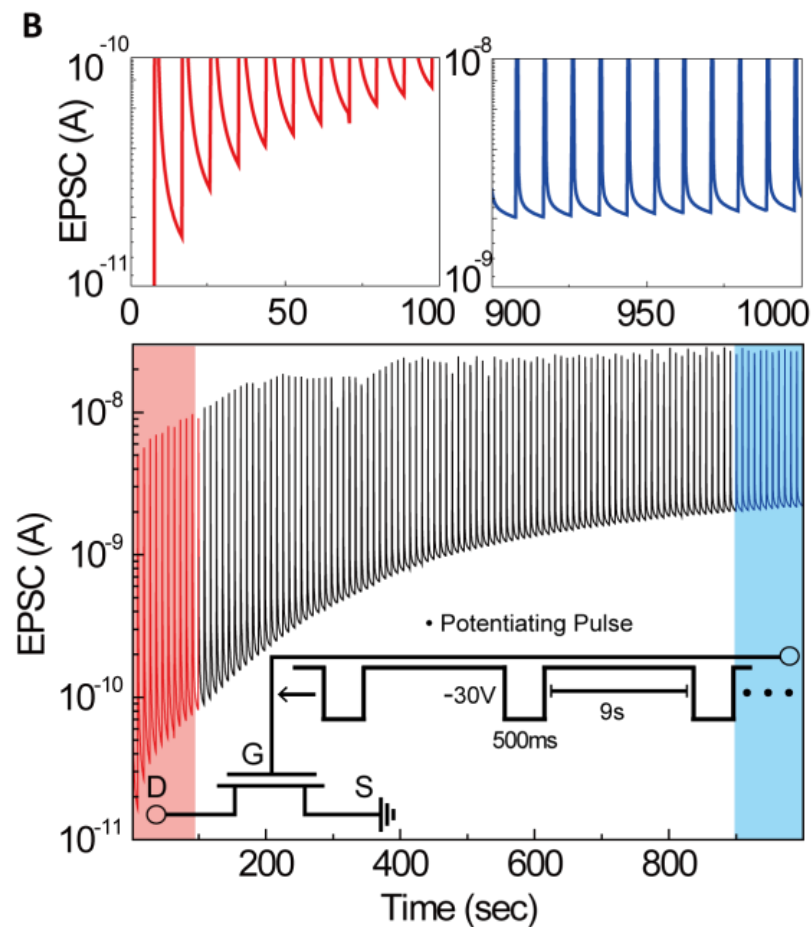
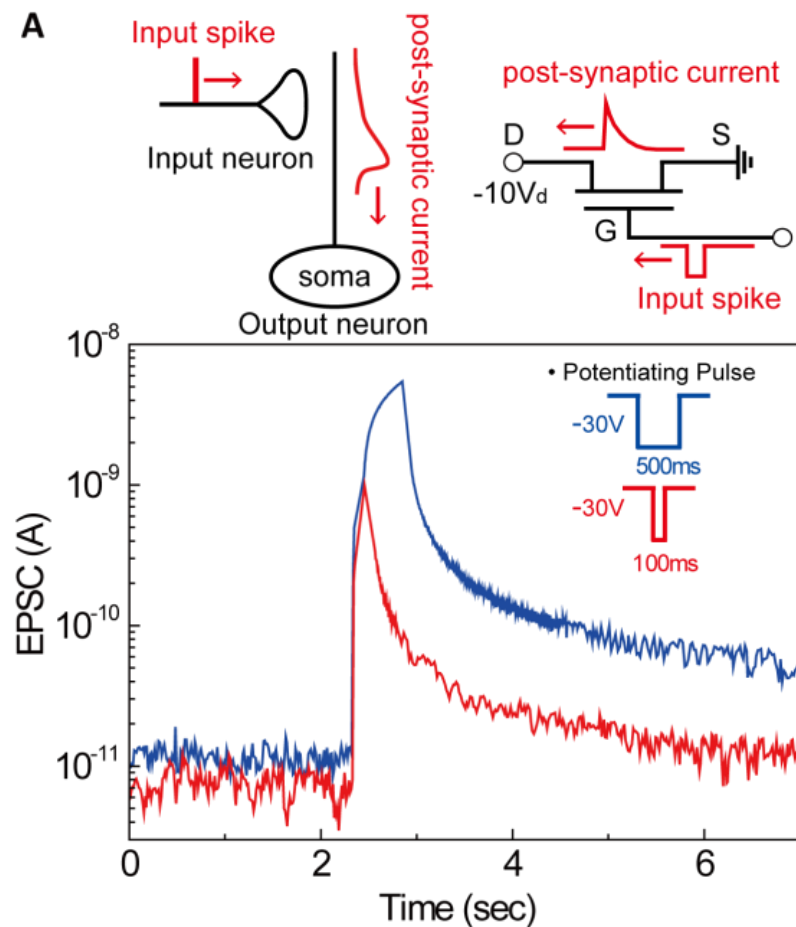


Ferroelectric organic neuromorphic transistors (FONTs)

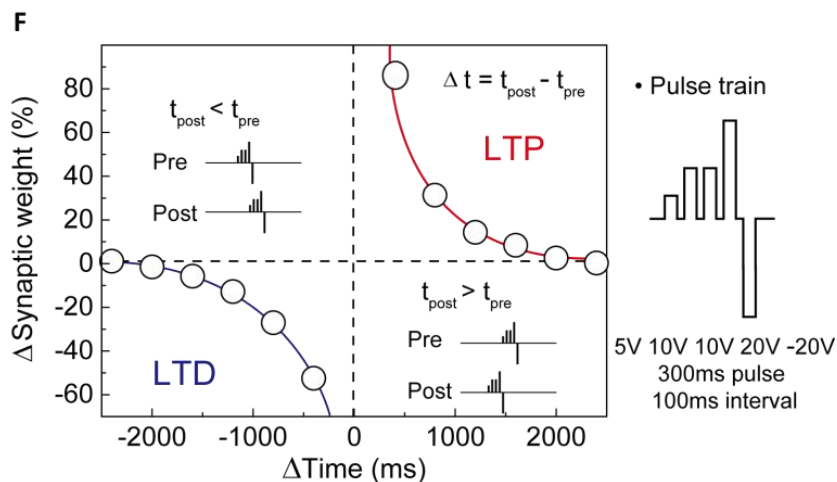
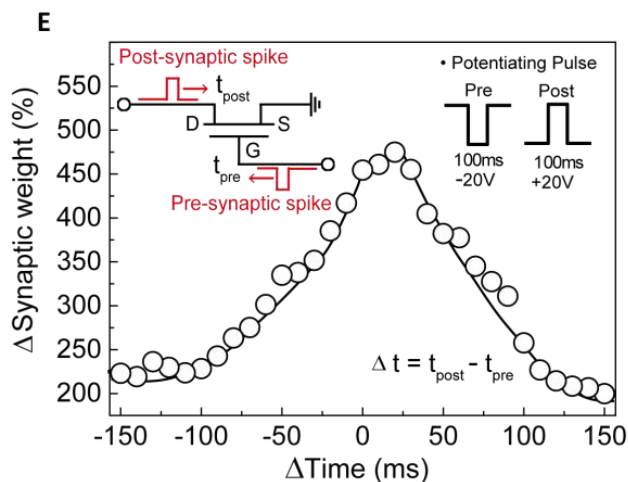
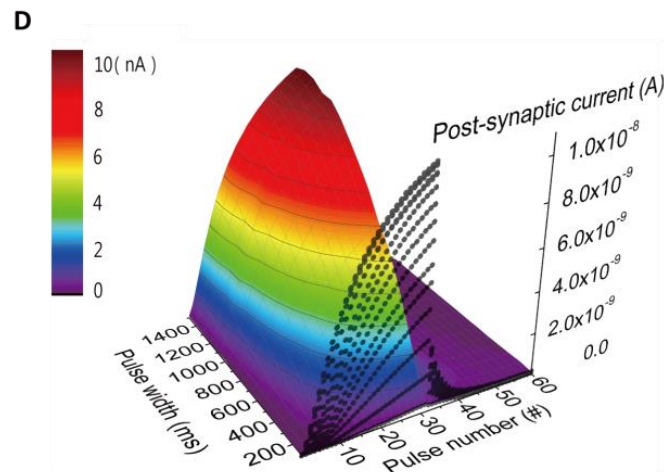
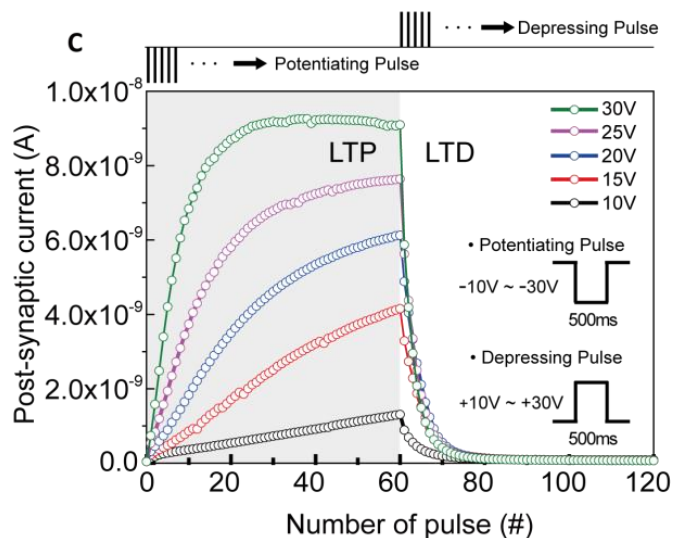
- Video of I-V characteristics of Free-standing Ferroelectric organic neuromorphic transistors (FONTs)



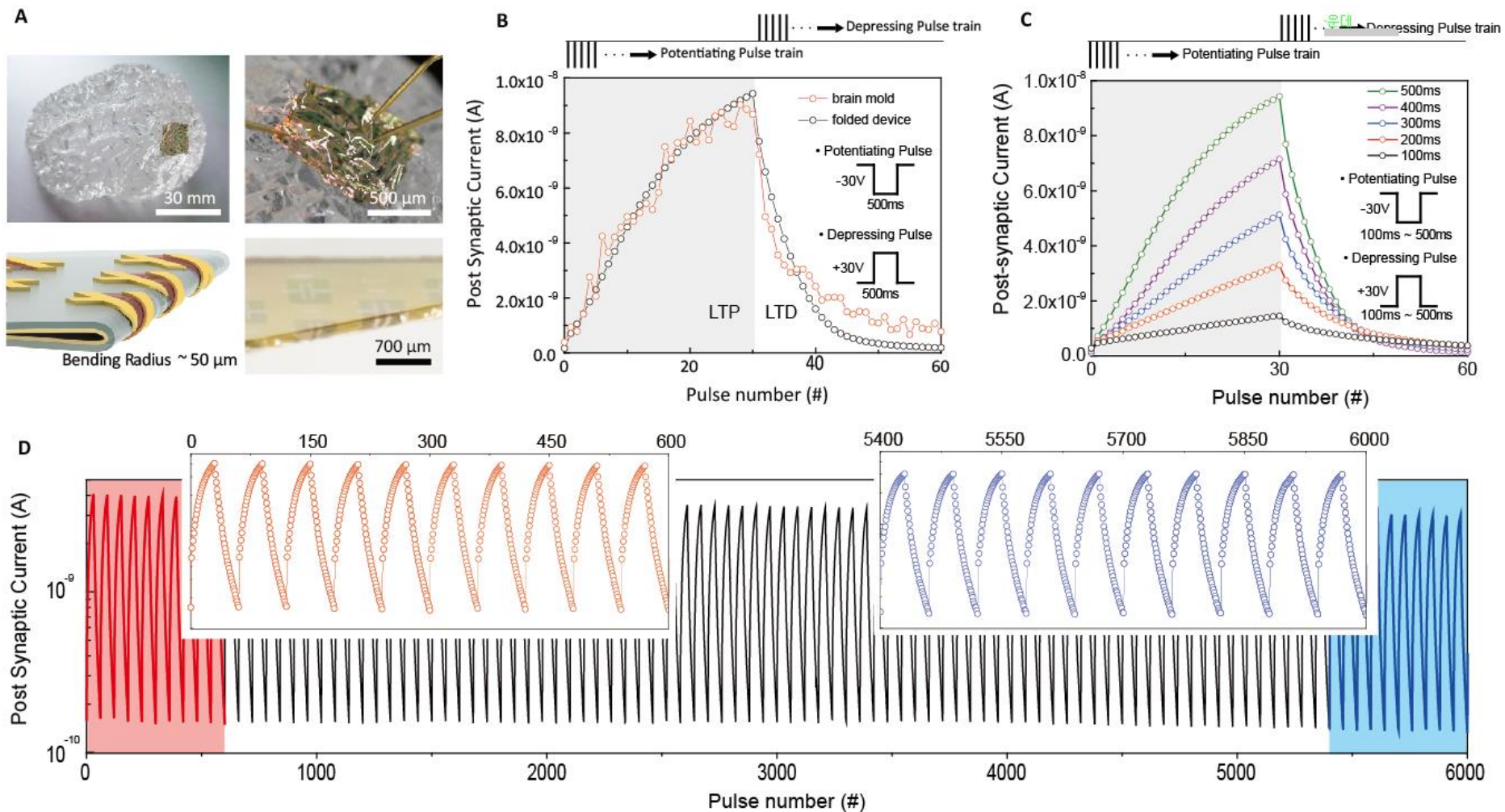
Ferroelectric organic neuromorphic transistors (FONTs)



Ferroelectric organic neuromorphic transistors (FONTs)



Ferroelectric organic neuromorphic transistors (FONTs)

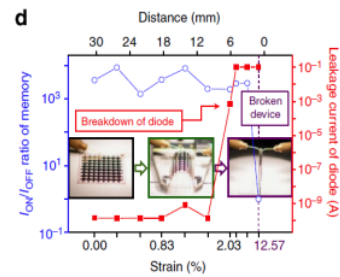
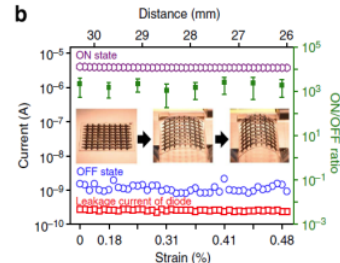
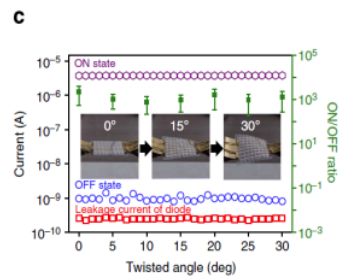
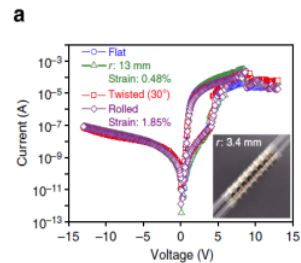
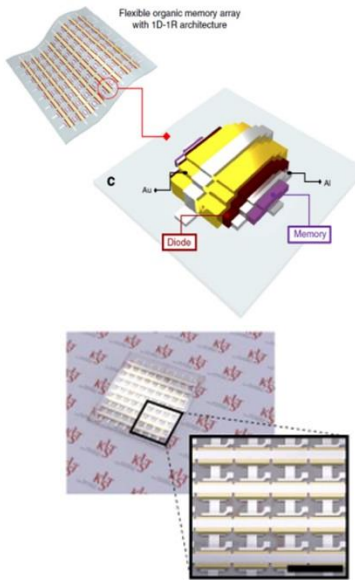


Next-generation Wearable Device Platform

Fibriform Organic Memory Transistors

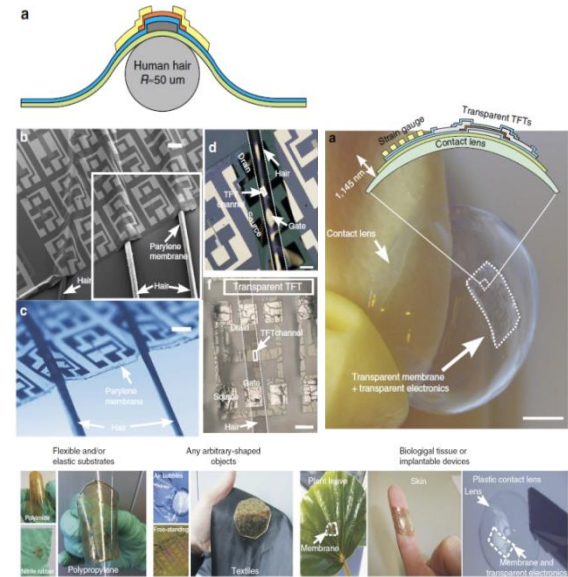
Previous Research on Flexible Devices

Flexible, Twistable, Rollable memory



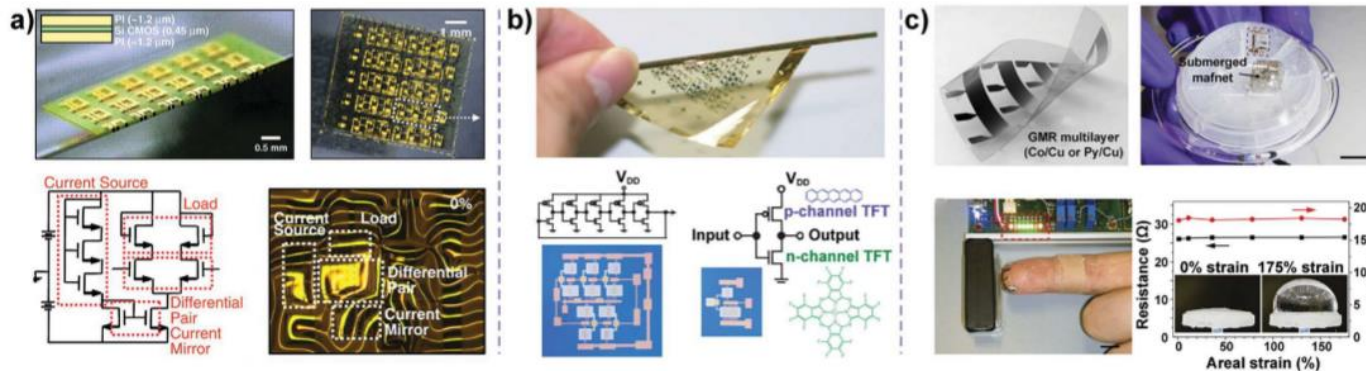
Nature Comm., 4, 2707 (2013)

Flexible Transferable device



Nature Comm., 5, 2982 (2014)

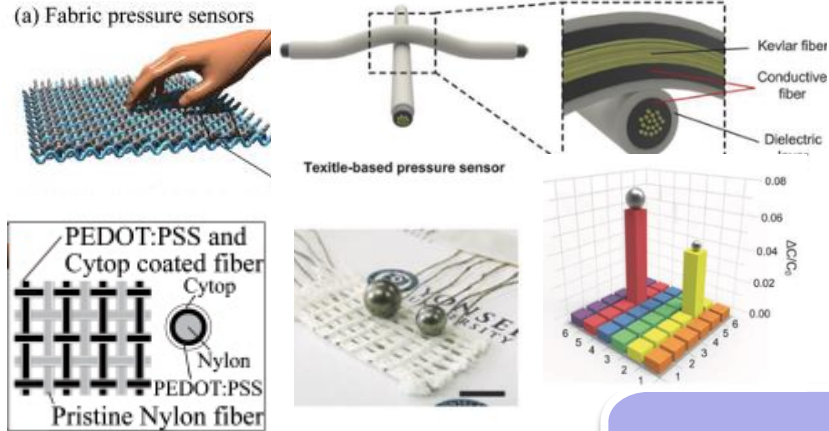
Stretchable, Rollable electronic circuit on flexible substrate



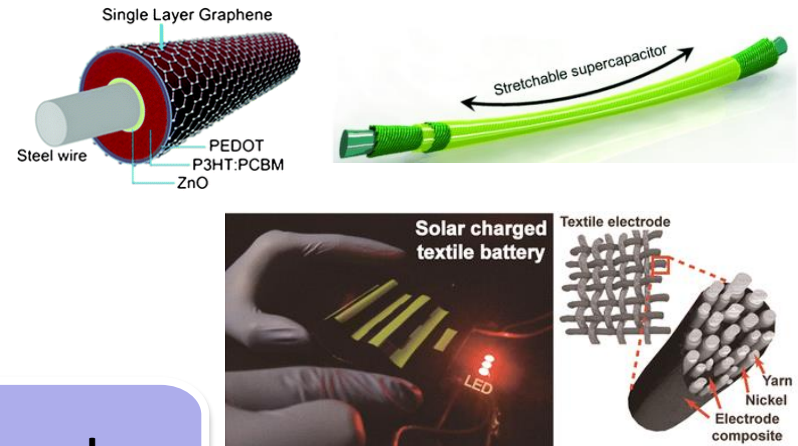
Science, 320, 507 (2008)
 Nat. Mater., 9, 1015 (2010)
 Nat. Commun. 6, 6080 (2015)

Fiber-Shaped Electronic Devices

Sensors

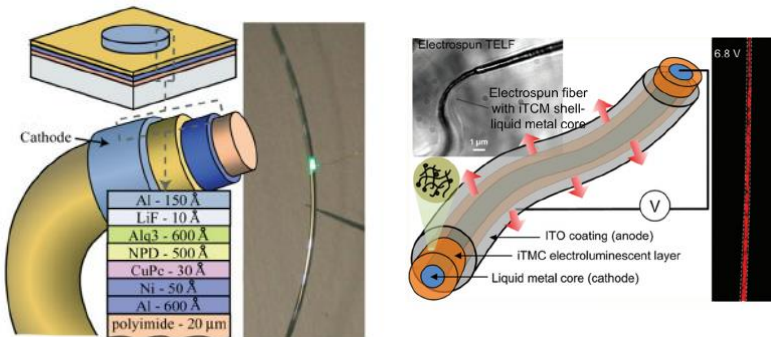


Energy devices

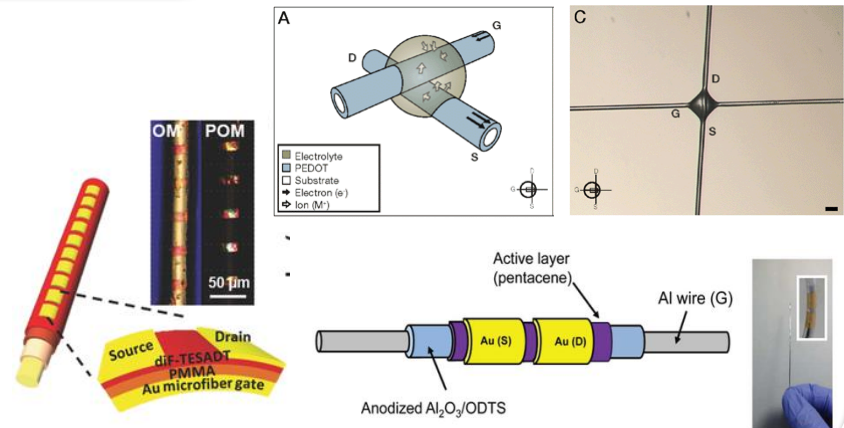


Fiber-shaped electronic devices

Light-emitting diode

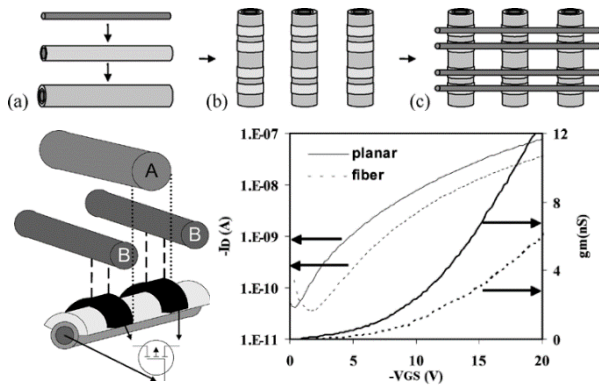


Transistors & Memories



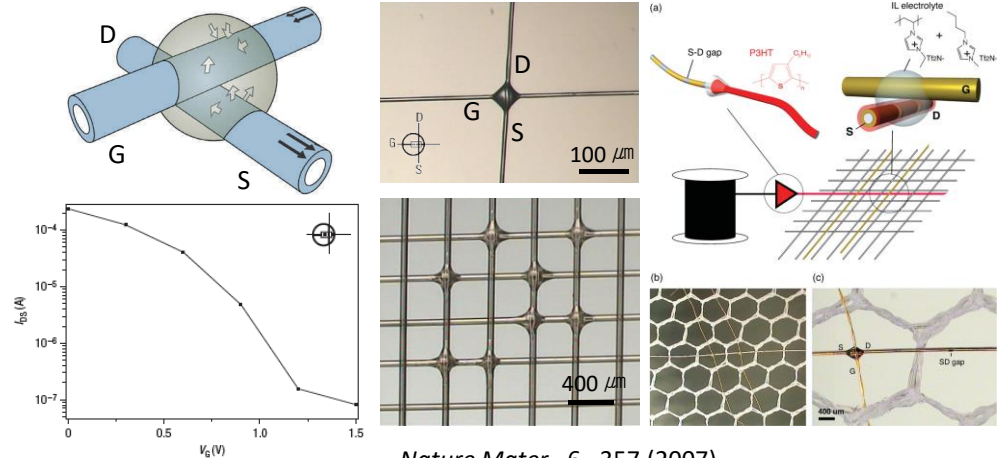
Previous Research on Fiber-type Electronic Devices

● Weaved OTFT on Fiber



IEEE Trans. Electron Dev., 52, 269 (2005)

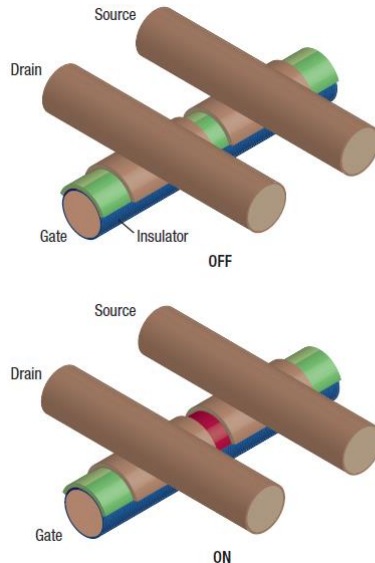
● Wire Electrochemical Transistors (WECTs)



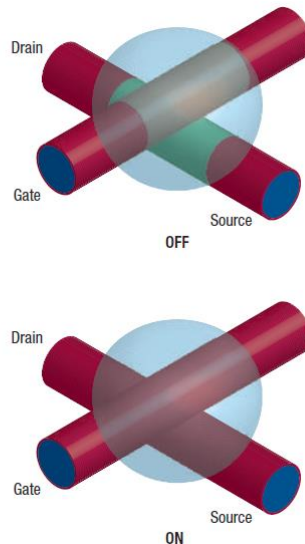
Nature Mater., 6, 357 (2007)

Adv. Mater., 21, 573 (2009)

● Fiber OFET



● WECT



- Insulator
- Conductor
- Semiconductor in the low-conduction state
- Semiconductor in the high-conduction state
- Ion reservoir

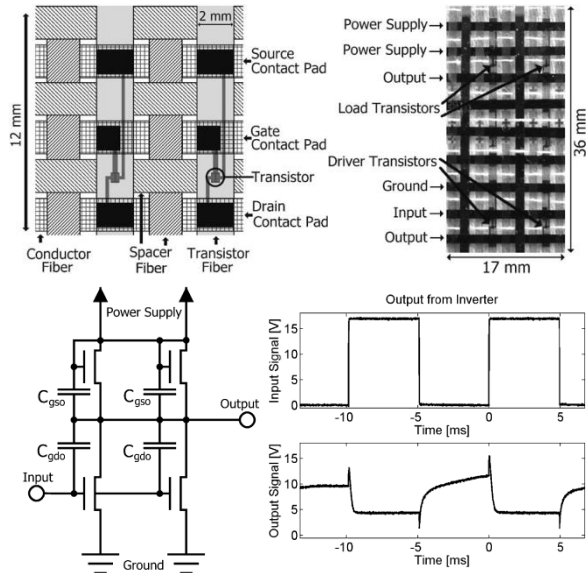
Nature Mater., 6, 328 (2007)

Adv. Mater., 26, 5310 (2014)

Category	Fiber OFET	WECT
Mobility	$>0.5 \text{ cm}^2 \text{ V}^{-1} \text{ s}^{-1}$ [76] Up to $1.4 \text{ cm}^2 \text{ V}^{-1} \text{ s}^{-1}$	Very low
Operating voltages	About 9–20 V	0–1.5 V
On/off ratio	10^3 – 10^5	10^2 – 10^3

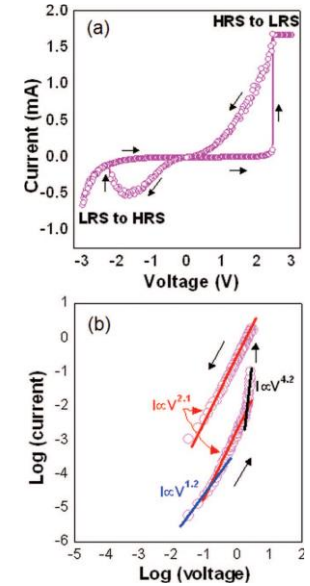
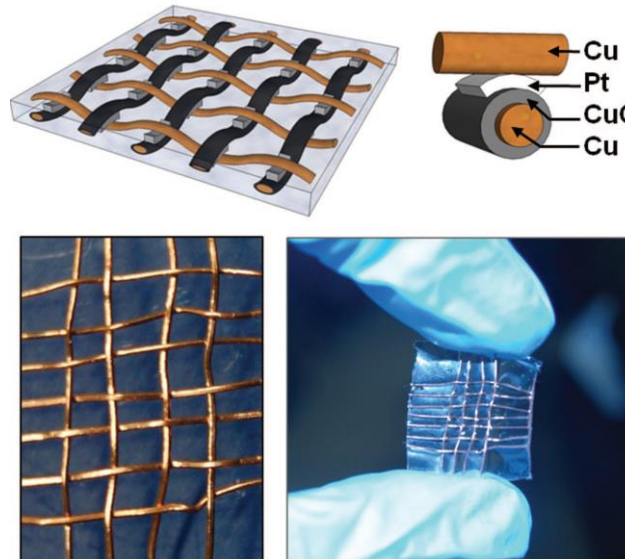
Previous Research on Fiber-type Electronic Devices

Woven Inverter circuit



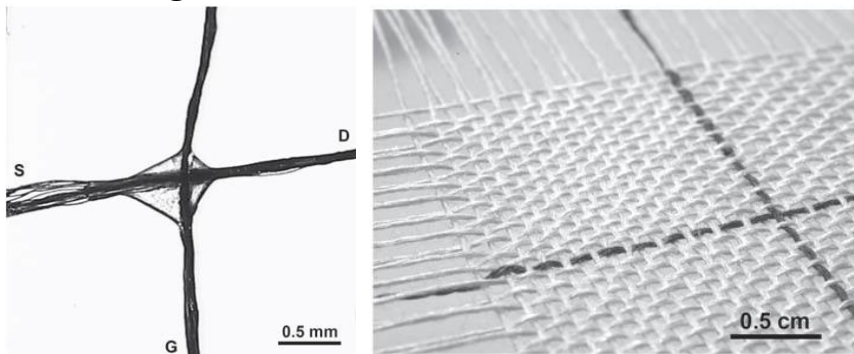
IEEE EDL, 25, 295 (2004)

Woven Resistive Memory Array



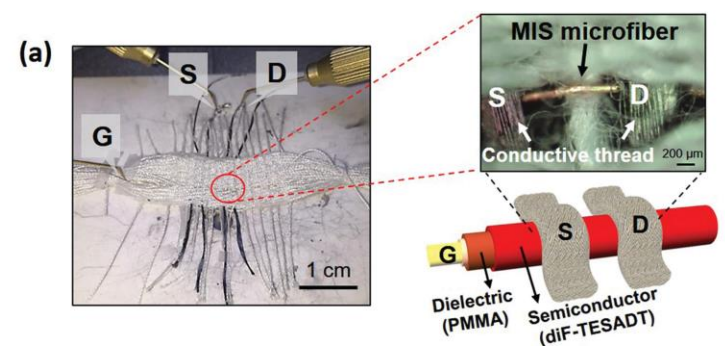
AIP Advances 1, 032162 (2011)

Weaving with silk fabric



Adv. Mater., 23, 898 (2011)

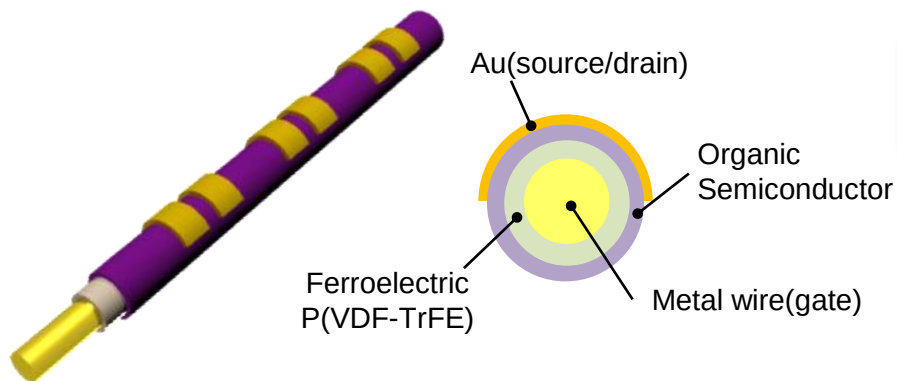
Fibriform OFET embedded in the textile



Adv. Funct. Mater. 26, 2706 (2016)

Fiber-Shaped Organic Ferroelectric Memory Transistors

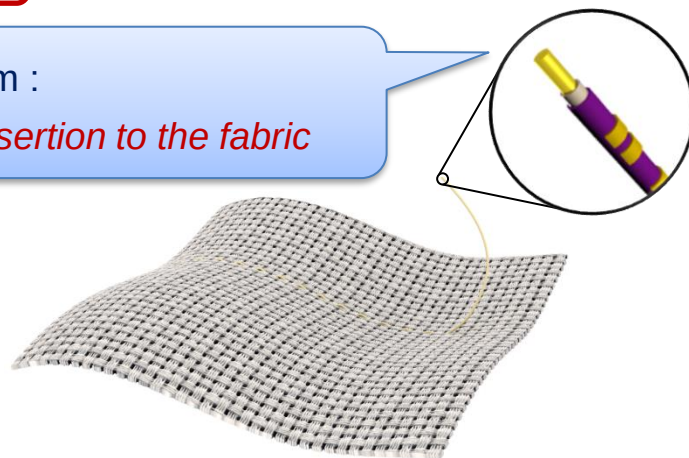
Target : 1-D memory transistors on single fiber



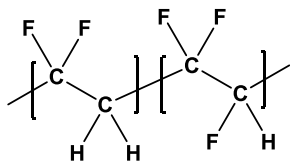
Fiber-shaped organic ferroelectric memory transistor

Final aim :

Fiber-insertion to the fabric

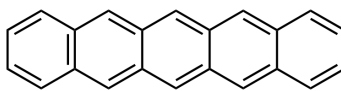


Materials



P(VDF-TrFE) copolymer

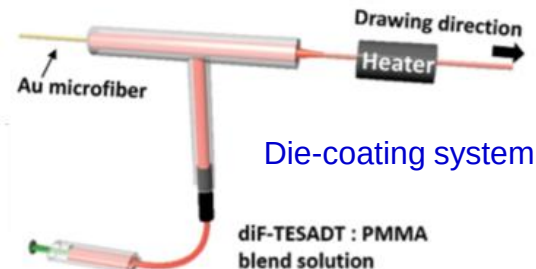
- Gate Dielectric
- Ferroelectric polymer
- Large remnant polarization
- Non-volatile memory application
- Solution processability



Pentacene

- Organic semiconductor
- P-type
- Thermal evaporation

Coating method



Adv. Funct. Mater. 2016, 26, 2706–2714

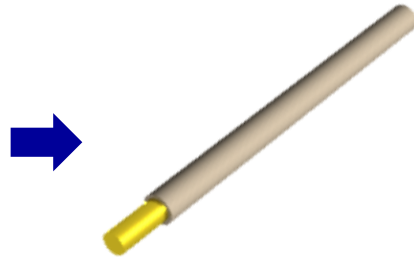
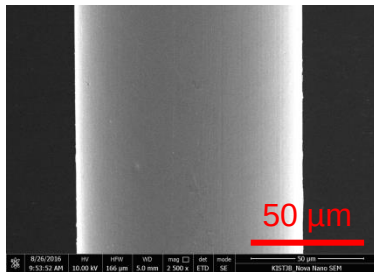
- Modified die-coating system
- Uniformly coating on the fiber

Fabrication procedure of fiber-shaped memory transistors

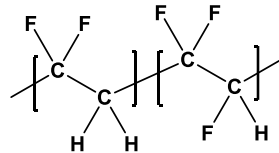


Metal wire

- Pristine gold wire
- Diameter: 100 μm



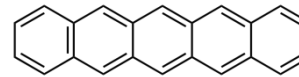
P(VDF-TrFE) coating



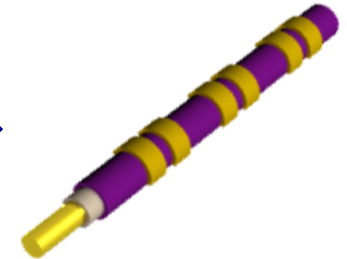
- 30 wt% P(VDF-TrFE) in DMF
- **Capillary tube coating system**
- Capillary tube(I.D.: 1.1~1.2mm)
- Coating rate: 30 mm/min
- Drying: convection oven, 140°C, 2h



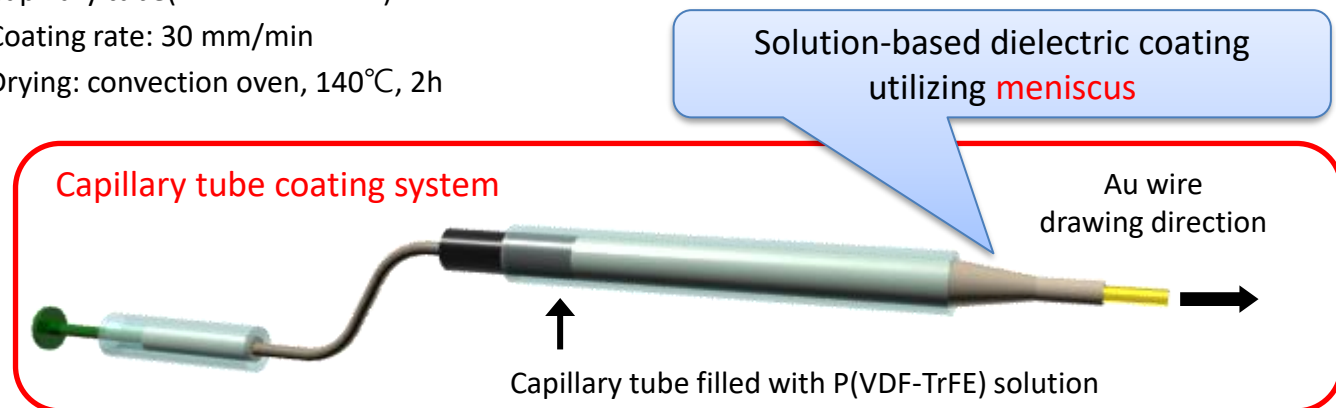
Organic Semiconductor



- Pentacene(50nm)
- Thermal evaporation

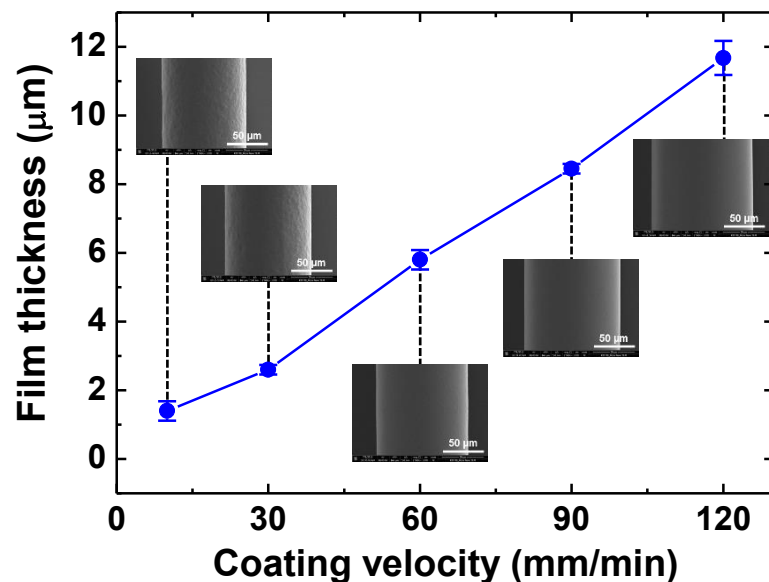


S/D electrode

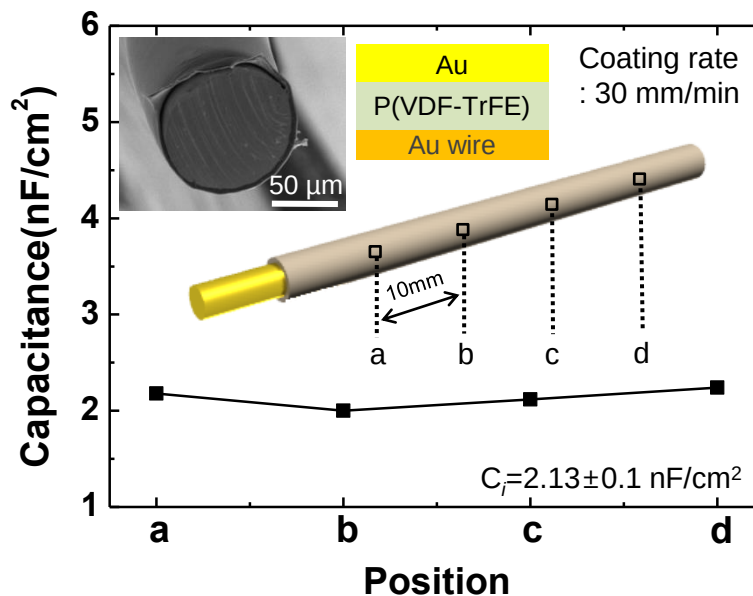


Uniformity of coated P(VDF-TrFE) film on the Au wire

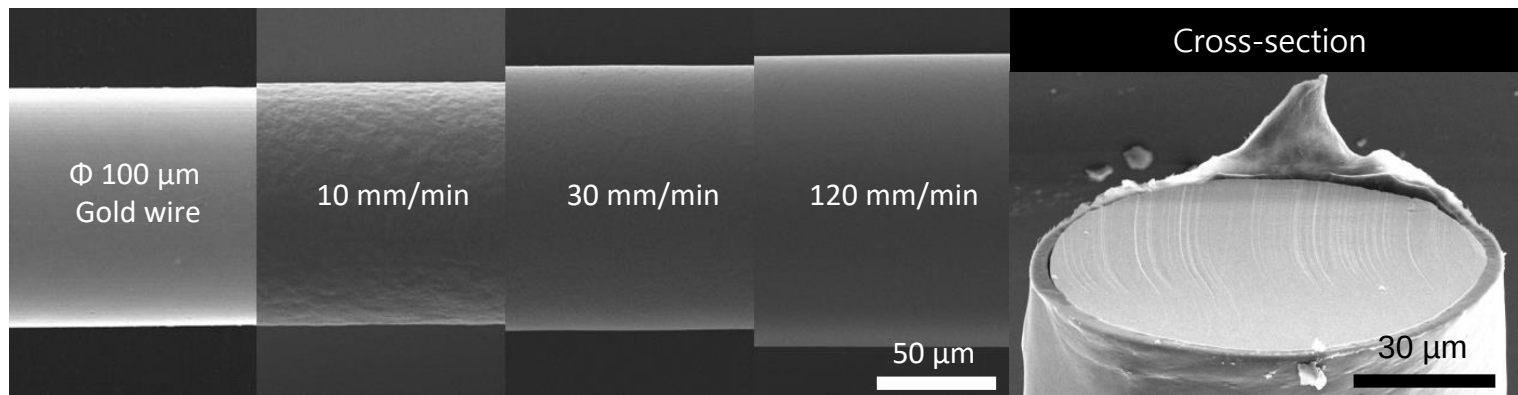
- Film thickness of P(VDF-TrFE)



- Capacitance of P(VDF-TrFE)

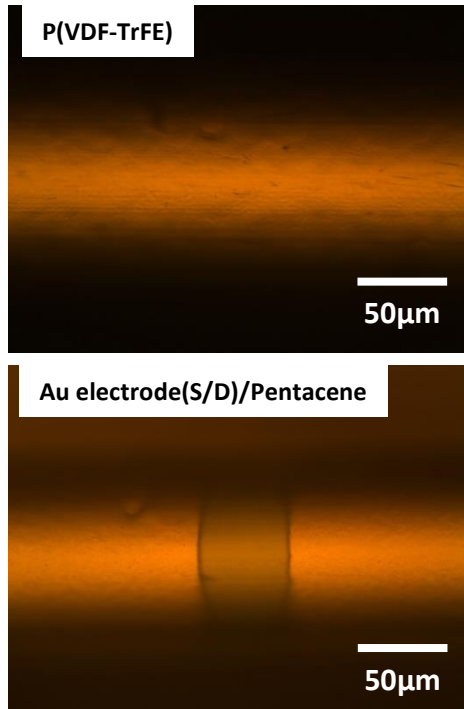


- Film thickness control depending on the coating speed

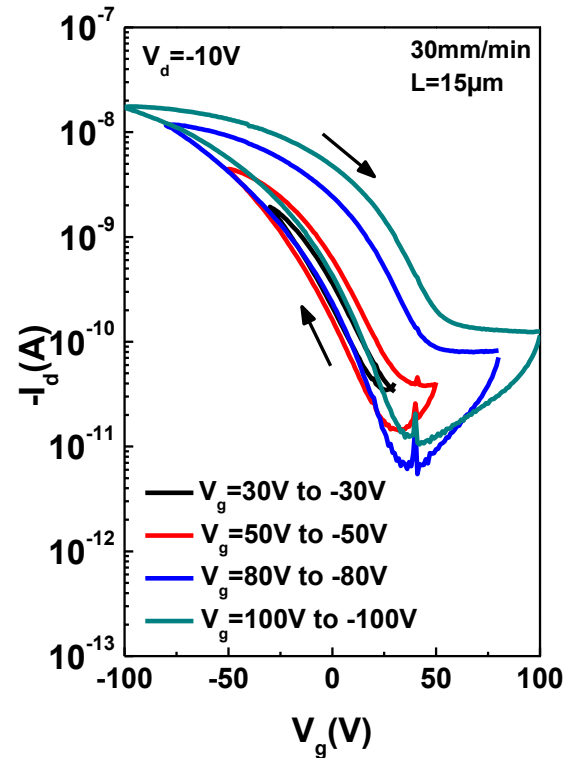


Device performances

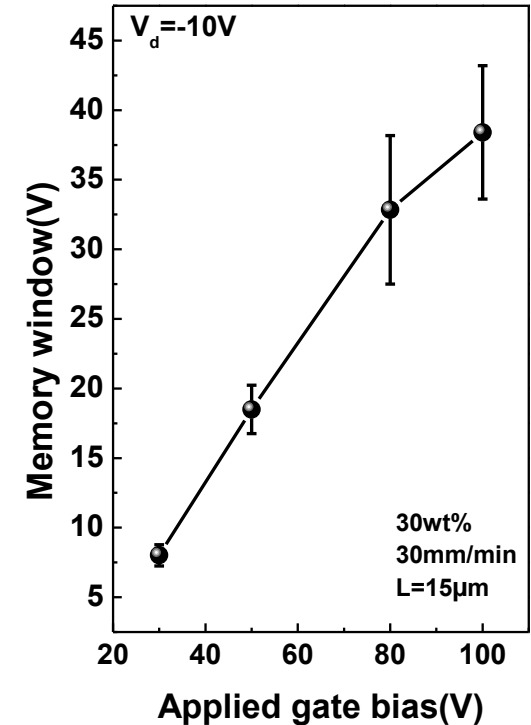
- Optical microscope image



- Double sweep transfer curve



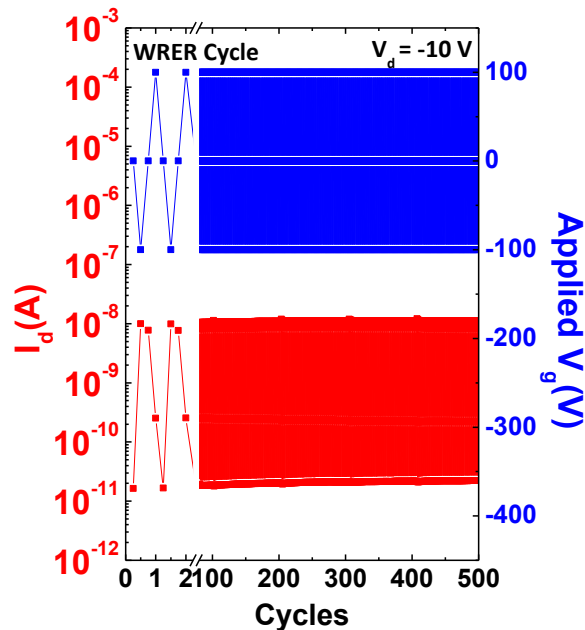
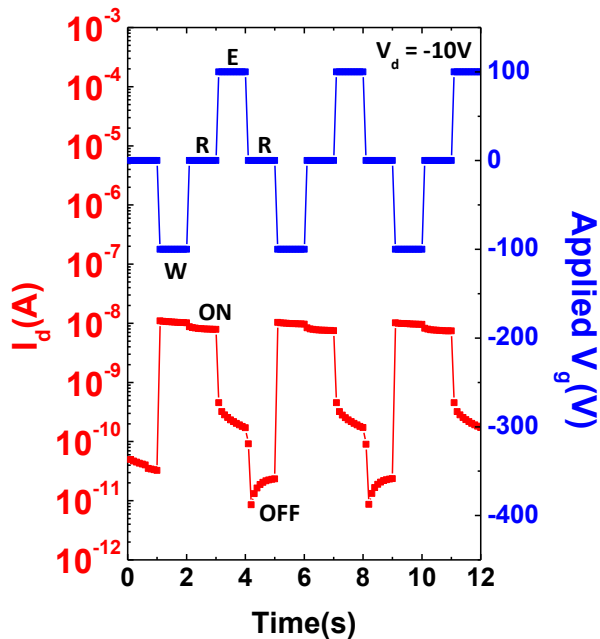
- Memory window



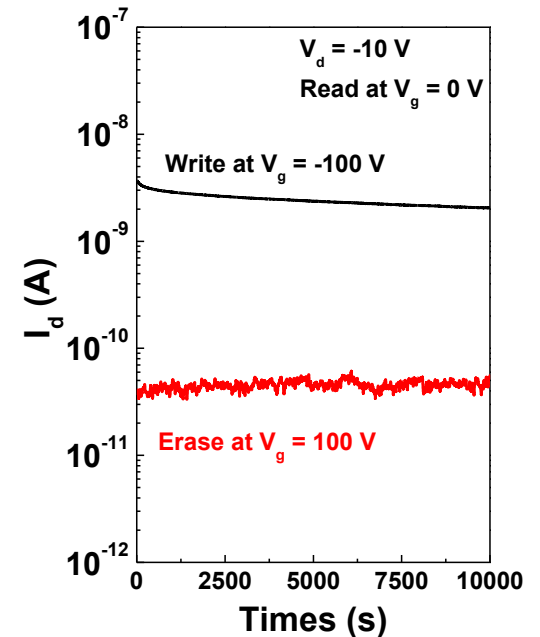
- The double sweep transfer curve showed a hysteresis loop, with a clockwise trace..
- When the gate bias sweep ranges were 30 V to -30 V, 50 V to -50 V, 80 V to -80 V, and 100 V to -100 V, the memory windows were approximately 8 V, 18 V, 33 V, and 38 V.

Device performances

- Write-Read-Erase-Read cycles



- Retention characteristics

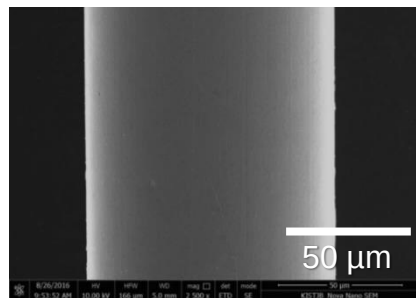


- The reversible switching properties were characterized by performing the Write/Read/Erase/Read(W-R-E-R) cycling test more than 500 times. It is worth nothing that our fiber-shaped memory transistors have reversible switching characteristics and a non-destructive readout capability.
- The measured drain current difference between ON state and OFF state was more than two orders of magnitude for 10^4 s.

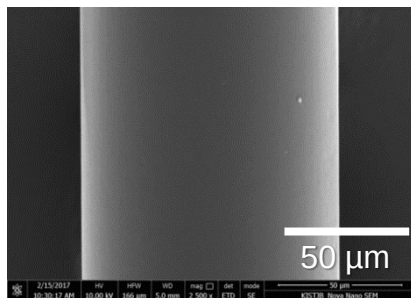
Gold, Aluminum and Silver wire

- Device structure: Au/Pentacene/P(VDF-TrFE)/Metal wire(Au, Al, Ag)

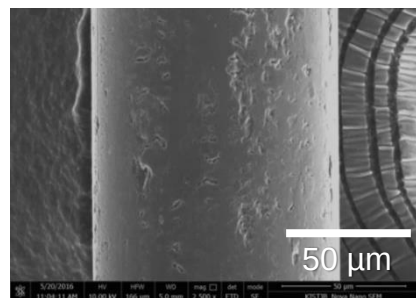
(a) Gold(Au) wire



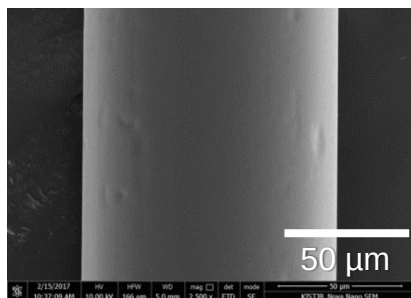
P(VDF-TrFE): 2.6 μm



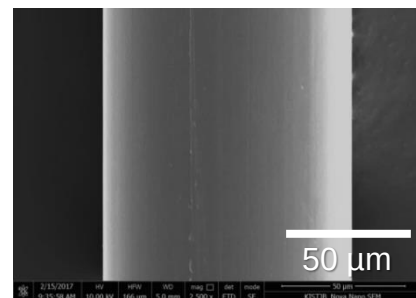
(b) Aluminum(Al) wire



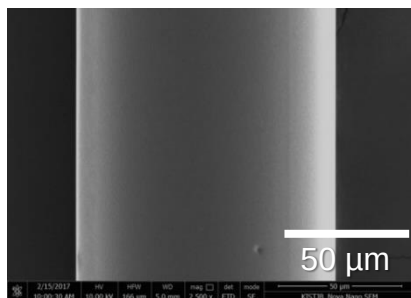
1.9 μm



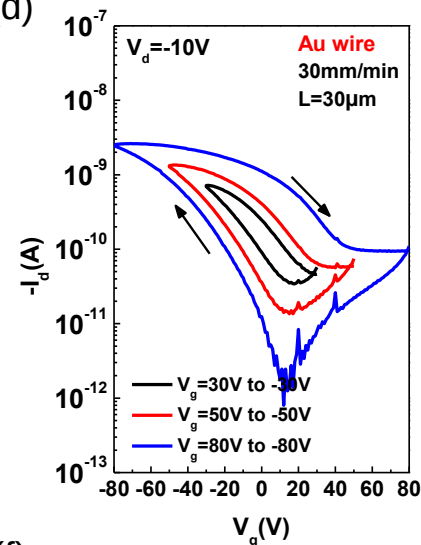
(c) Silver(Ag) wire



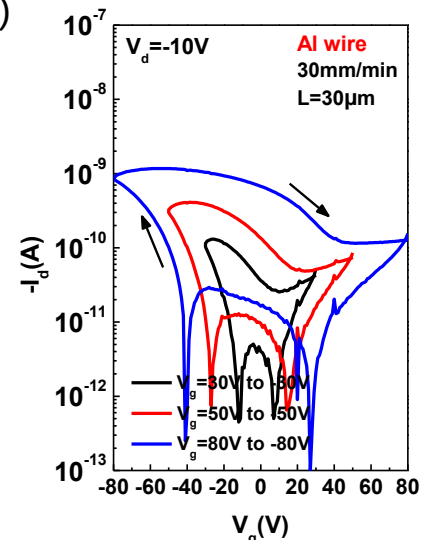
3.3 μm



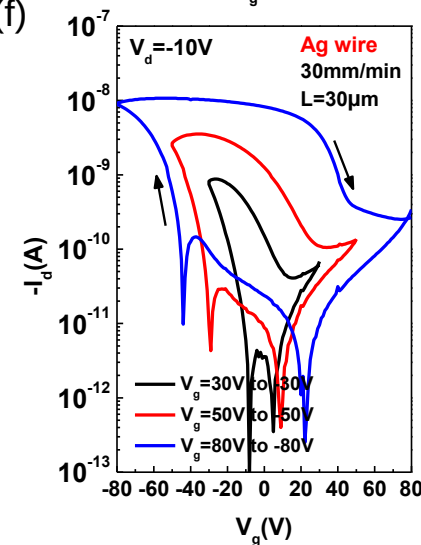
(d)



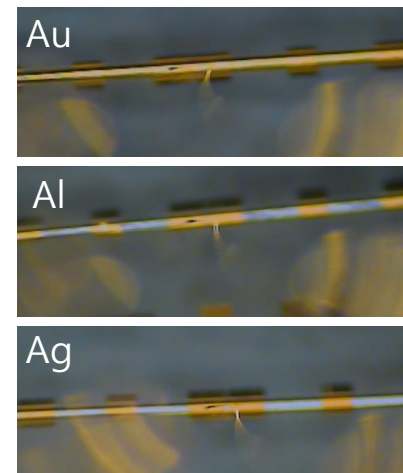
(e)



(f)



(g)

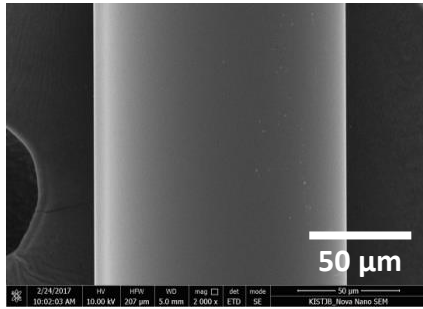


Optical fiber and Plastic fiber

- Device structure: Au/Pentacene/P(VDF-TrFE)/**Ag/Optical fiber or Plastic fiber**

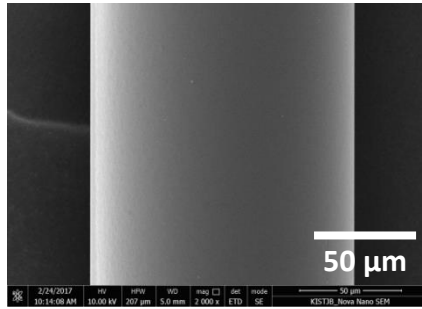
➤ SEM images

(a) Optical fiber(OptF)



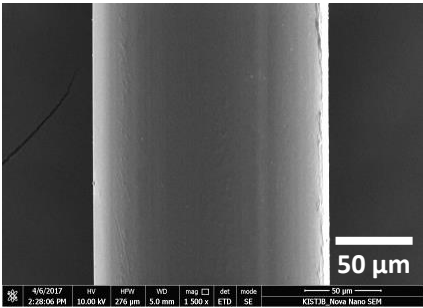
Diameter: 125 μm

(b) P(VDF-TrFE)/Ag/OptF



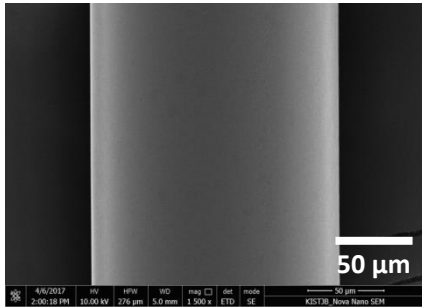
P(VDF-TrFE): 2.9 μm

(c) Plastic fiber(PF)



Diameter: 155 μm

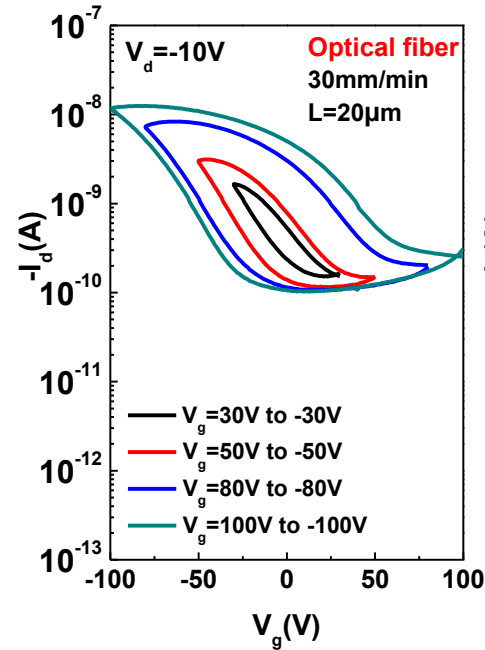
(d) P(VDF-TrFE)/Ag/PF



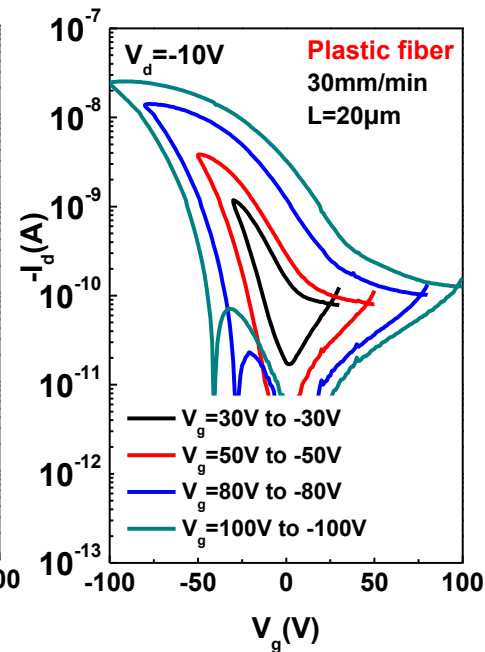
P(VDF-TrFE): 3.7 μm

➤ Transfer characteristics

Optical fiber



Plastic fiber

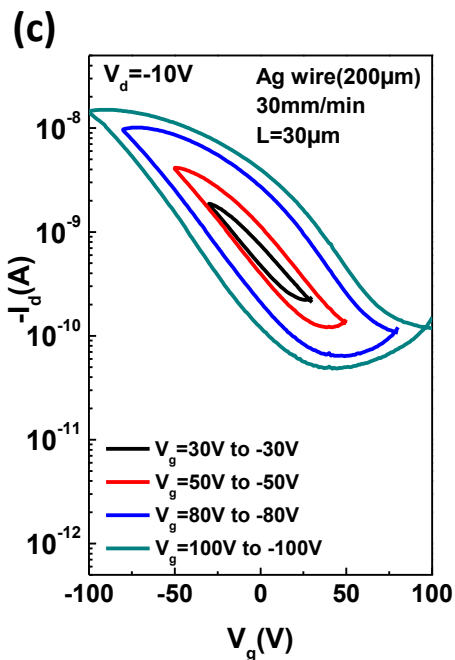
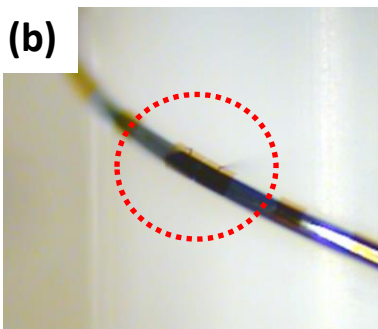
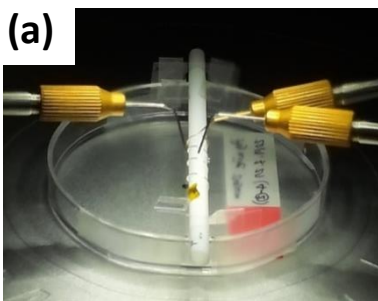


Optical fiber and Plastic fiber

- Device structure: Au/Pentacene/P(VDF-TrFE)/Ag wire

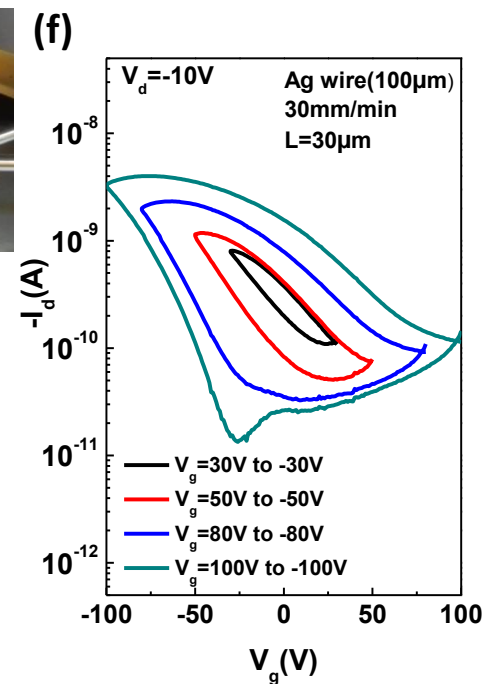
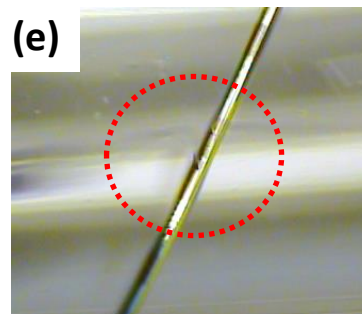
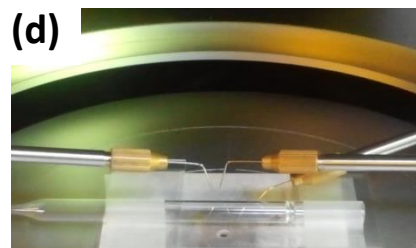
➤ Winding on straw

- Diameter of Ag wire: 200 μm
- Diameter of straw: 3.6 mm



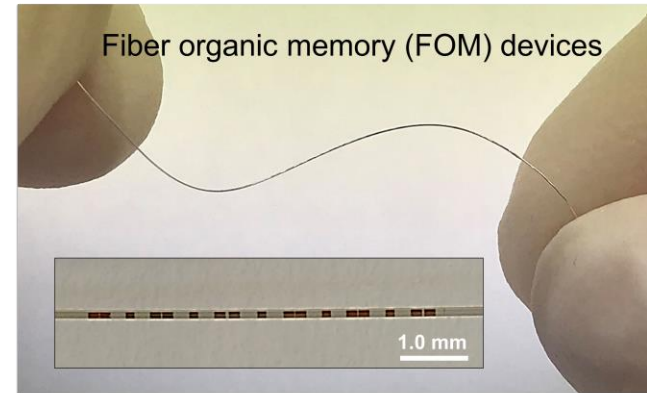
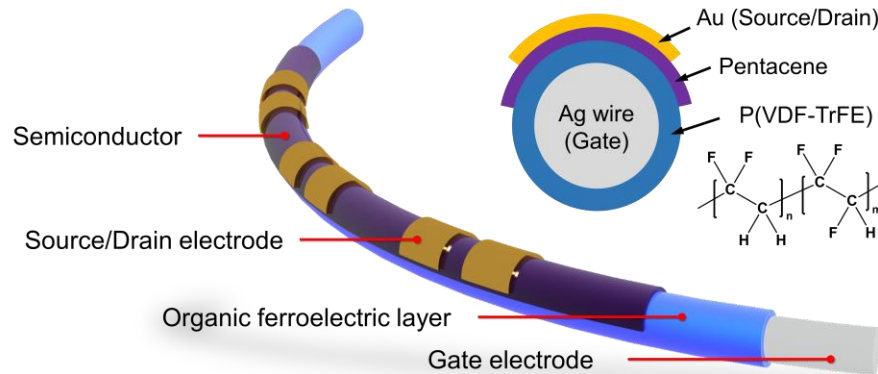
➤ Winding on glass pipette

- Diameter of Ag wire: 100 μm
- Diameter of glass pipette: 7.1 mm

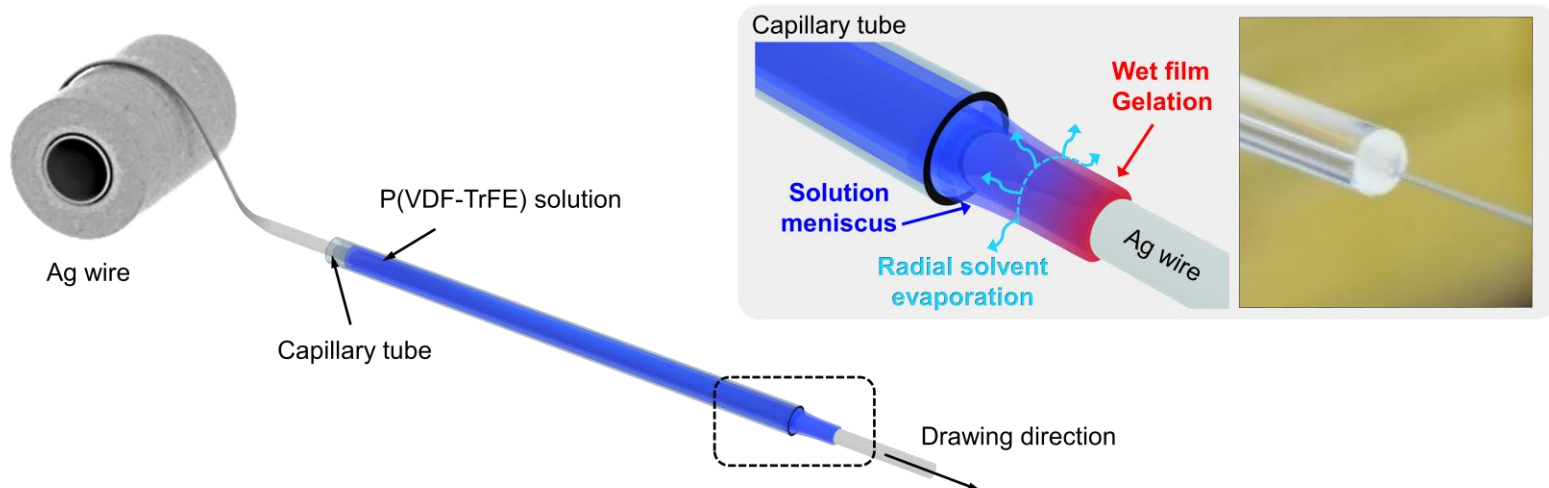


Low-Voltage Fiber memory Transistor

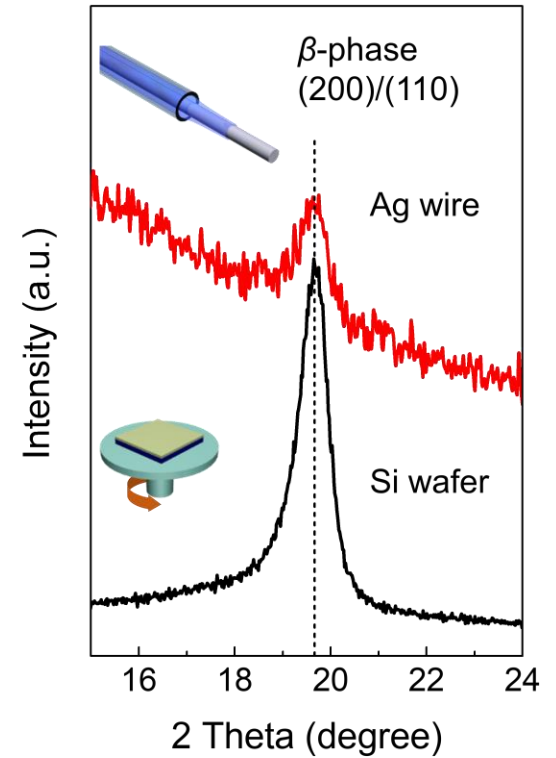
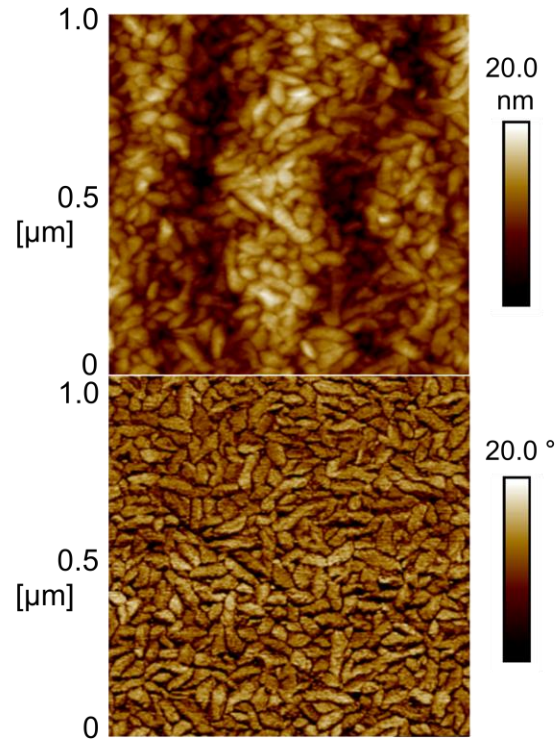
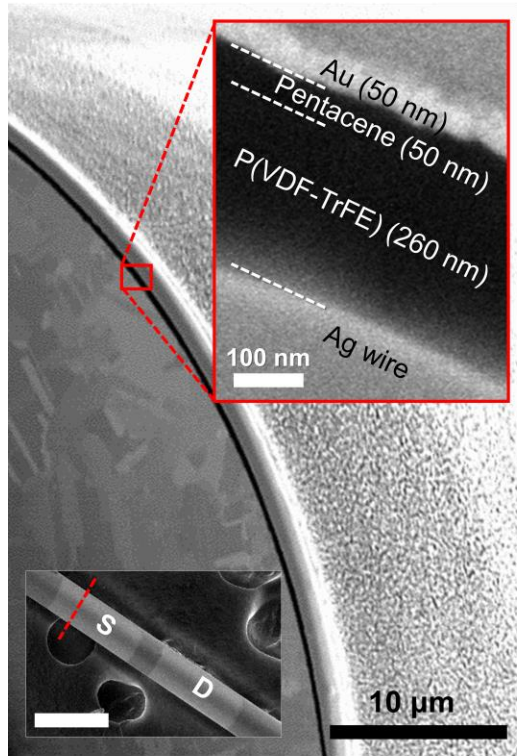
- Optimization of Coating process



Capillary Tube-Assisted Coating (CTAC) Process

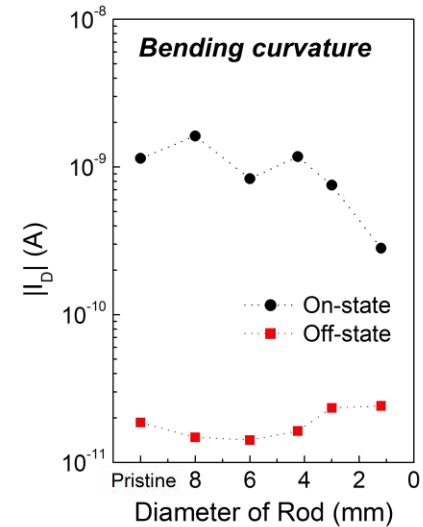
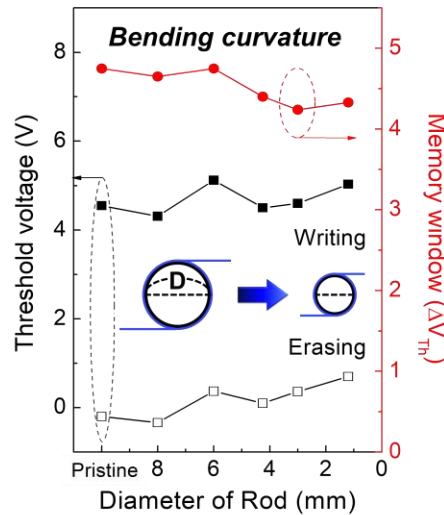
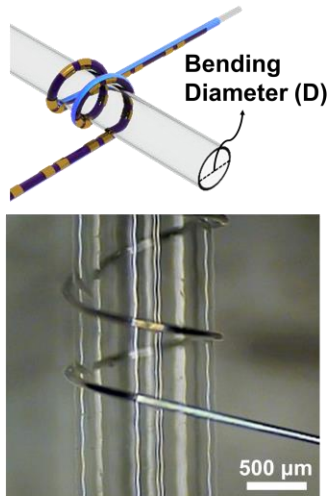
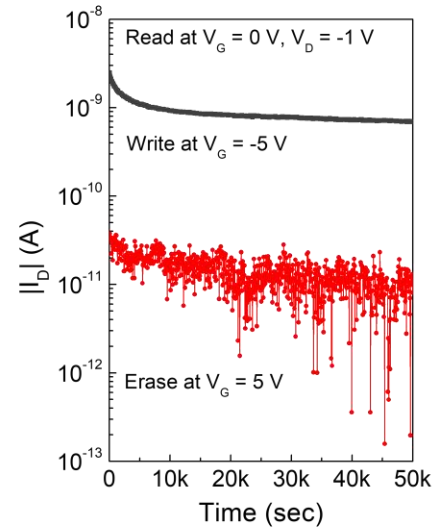
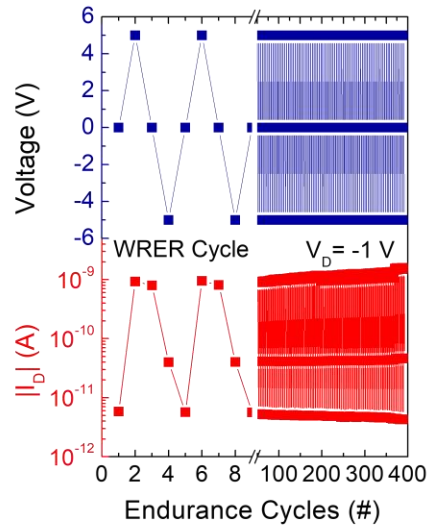
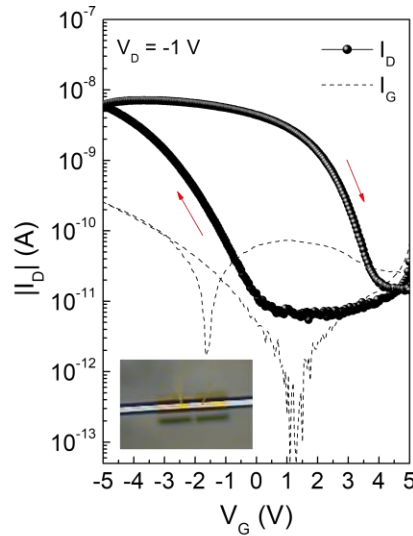


Low-Voltage Fiber memory Transistor



Low-Voltage Fiber memory Transistor

- Device Performances



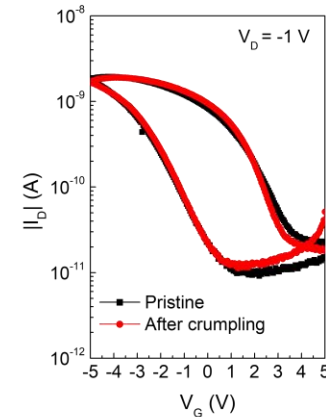
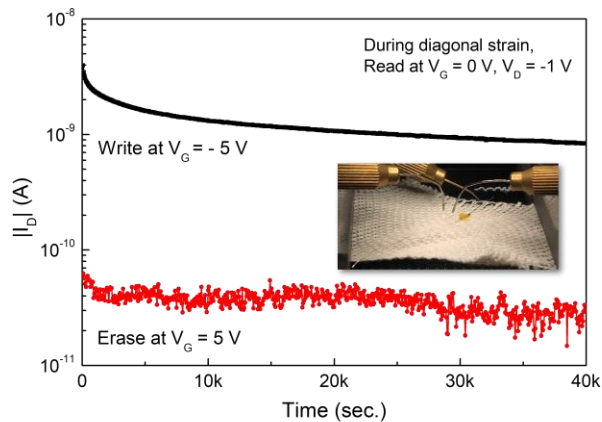
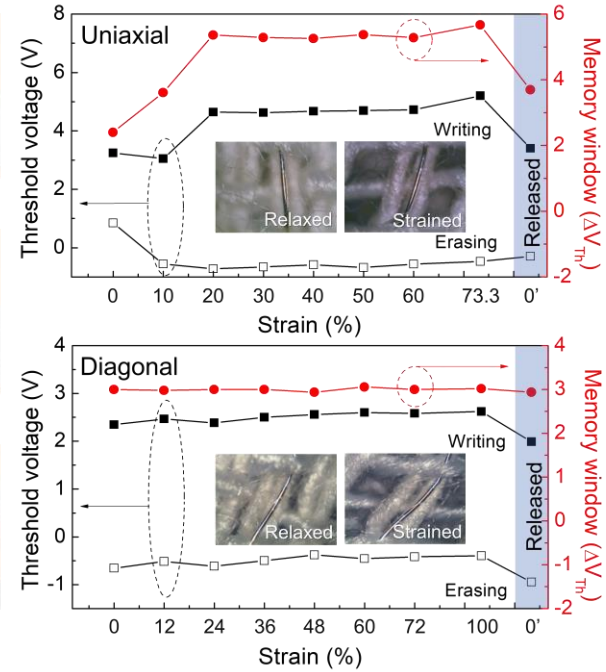
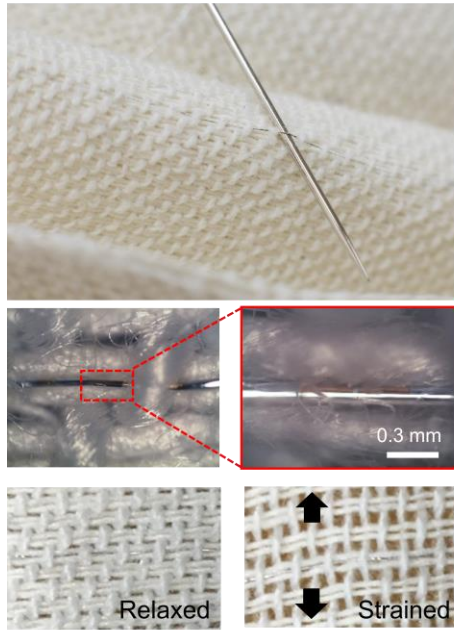
Low-Voltage Fiber memory Transistor

- Fiber memory in a textile



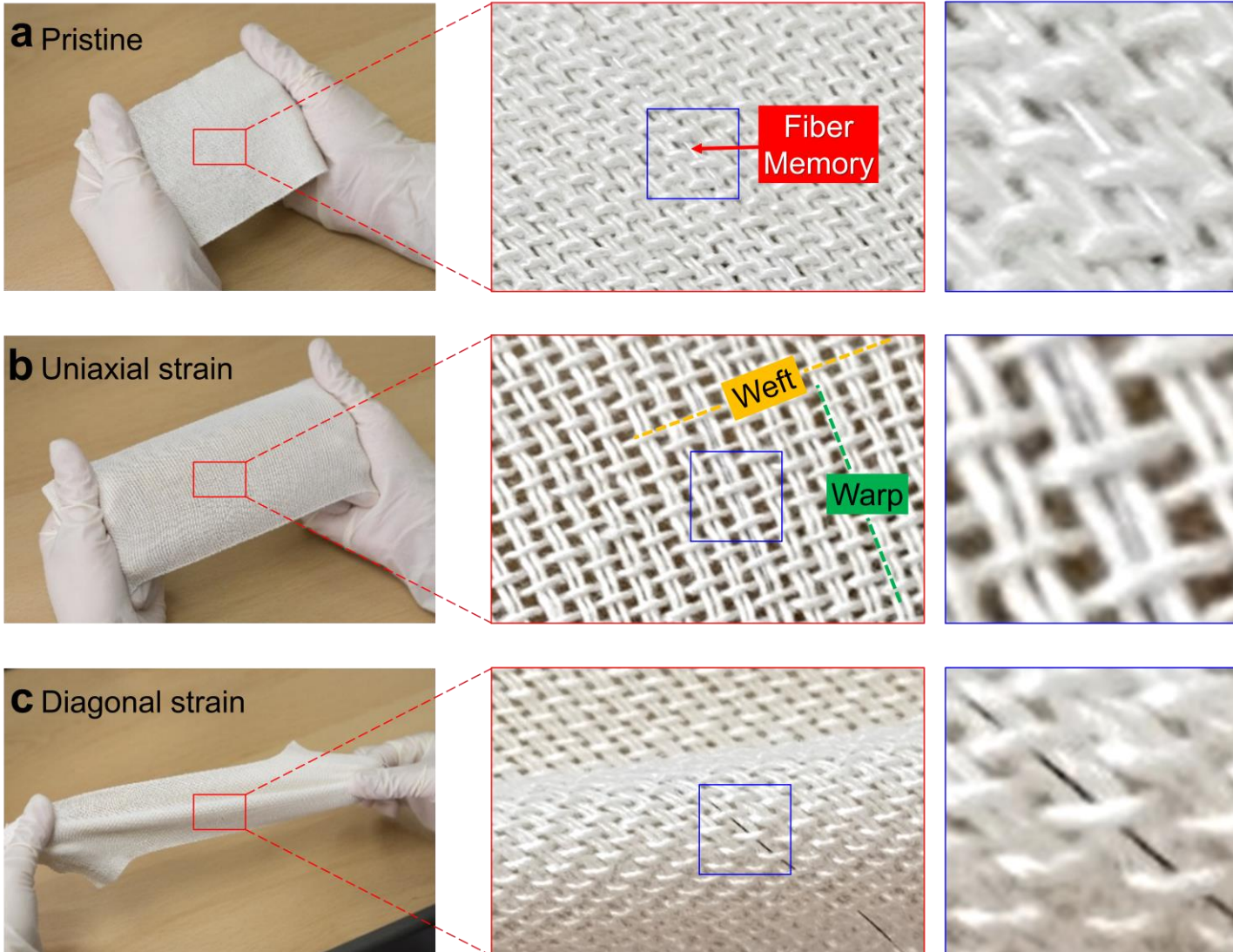
Low-Voltage Fiber memory Transistor

- Performance of Fiber memory in a textile



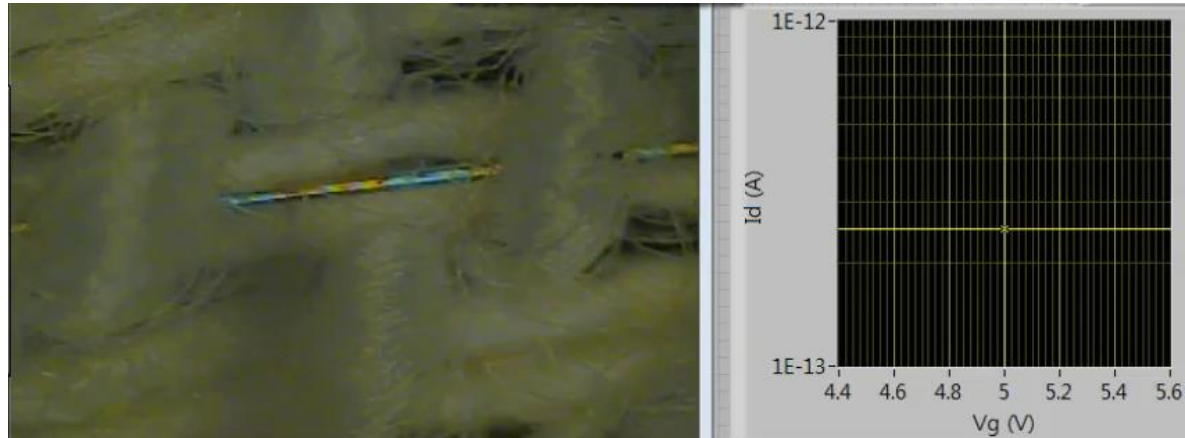
Low-Voltage Fiber memory Transistor

- Fiber memory in a textile under various strain conditions

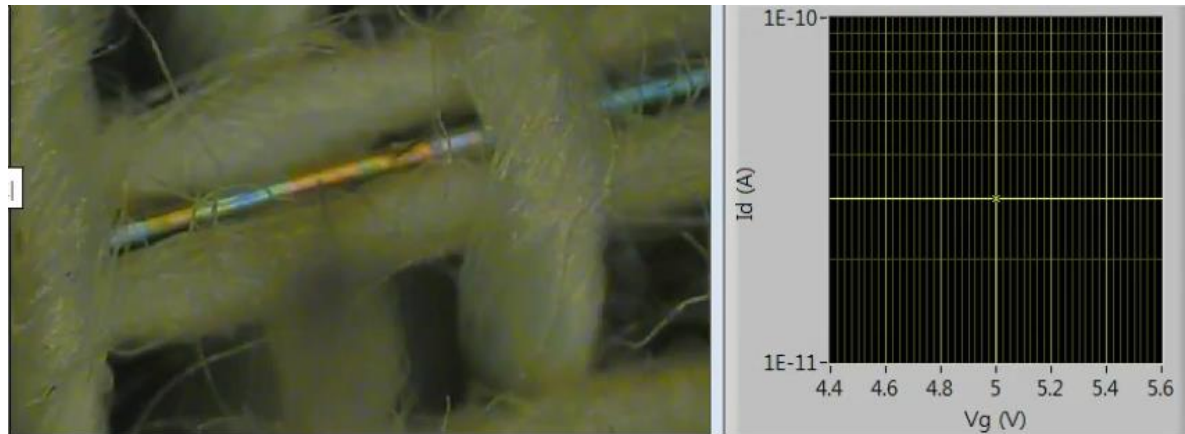


Low-Voltage Fiber memory Transistor

- Pristine



- 73.3 % strain



Next-generation Wearable Device Platform

Chip on a Fiber for New concept of E-Textile

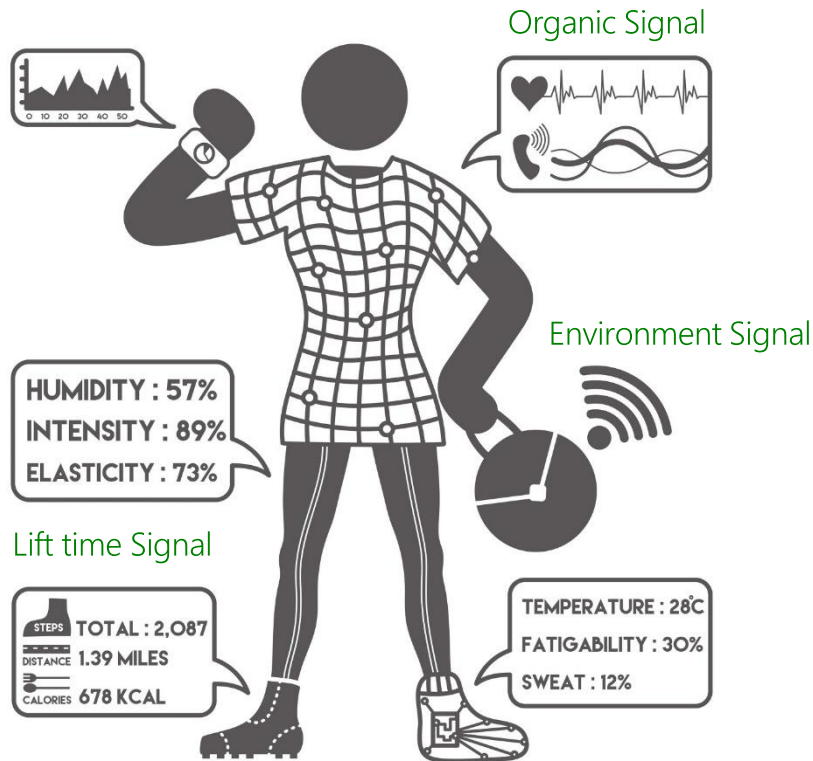
Future of Wearable Computer ?



Wearable Devices for Future Emerging Technology

● Requirements for Wearable Devices

■ Main concept of Wearable Devices



■ Functions (Performance)



■ Shape (Platform)



Interactive Device Technology

; The technology includes processing, sensing, displaying, memory, and transfer of the signals from human body environment

Perspectives on Wearable Devices

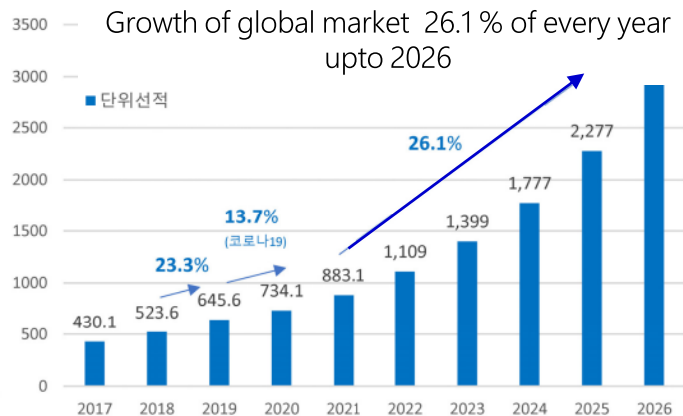
Expectation on the technology and market

Growing up glove market



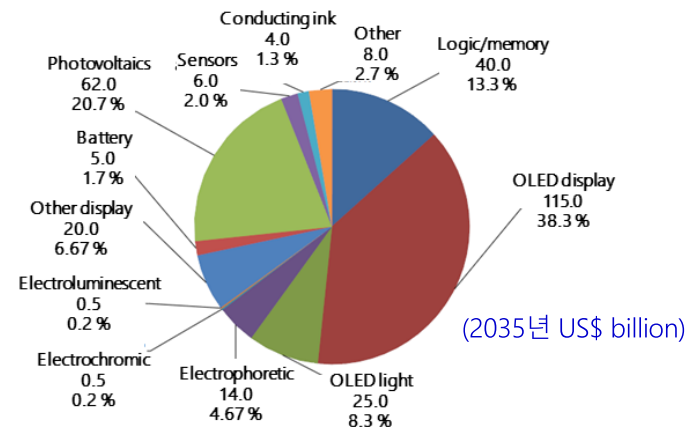
From: Credit Suisse(2013.5) The Next Big Thing-Wearable Are In Fashion

Perspectives on Global market



Form: Frost & Sullivan (2021)

Global market share of wearable technology

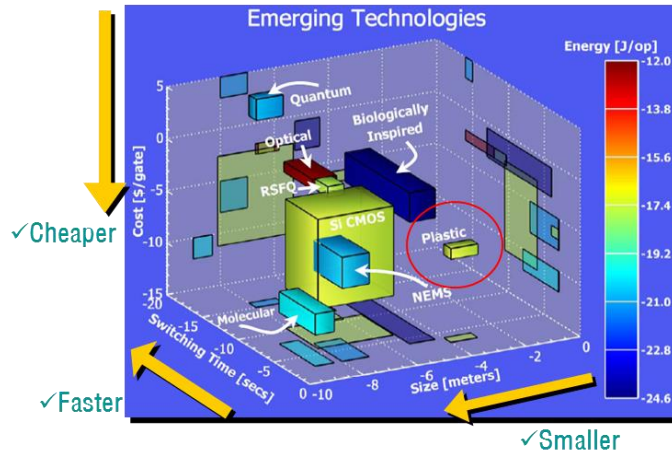


From: IDTechEx 2015-2025

Research Trend on Wearable Devices

● Research

■ Issues on emerging electronic devices

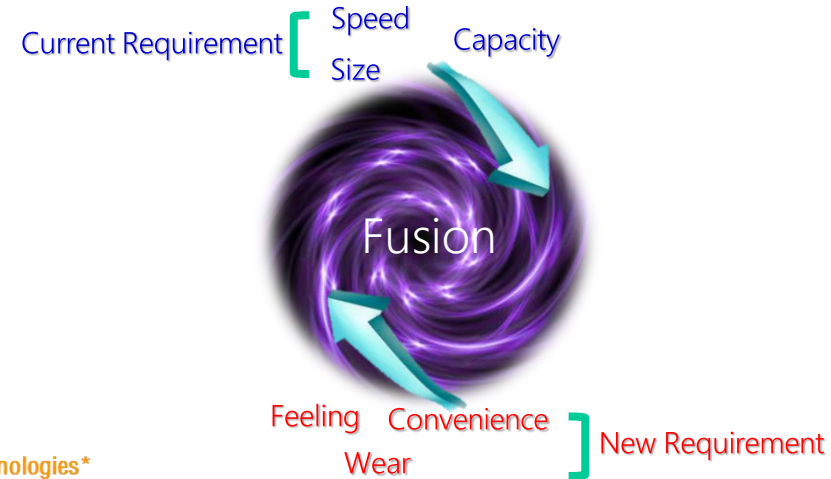


● From ITRS (International Technology Roadmap for Semiconductors) Roadmap Emerging Technologies*

Keywords

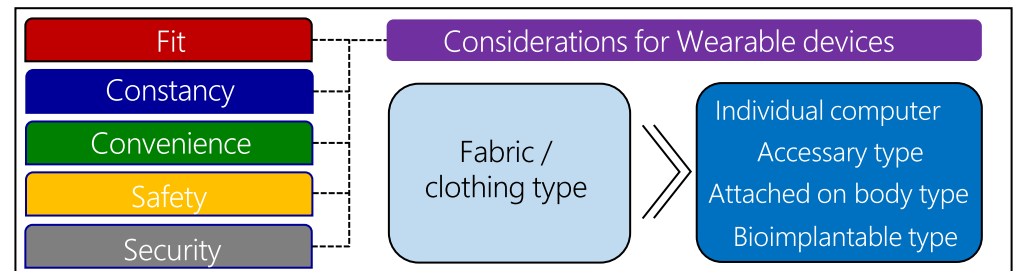
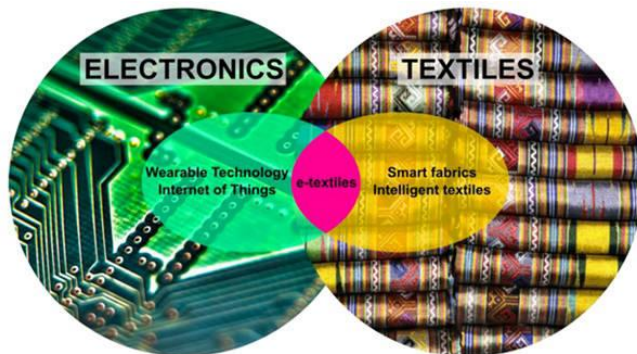
- Low cost
- Heat
- Synthesis
- Flexibility
- Printing
- Robustness
- Reliability
- Scaling down
- Uniformity

■ Requirements on Future Devices



■ Electronic Devices with various Functions and their shape

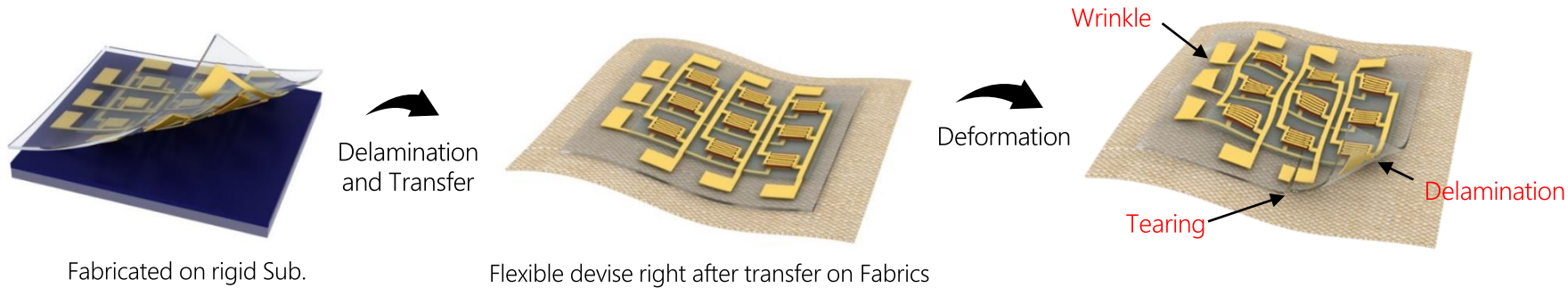
Electronic Textile: Implementation of Electronics on Fabrics or Fiber (non conventional substrate)



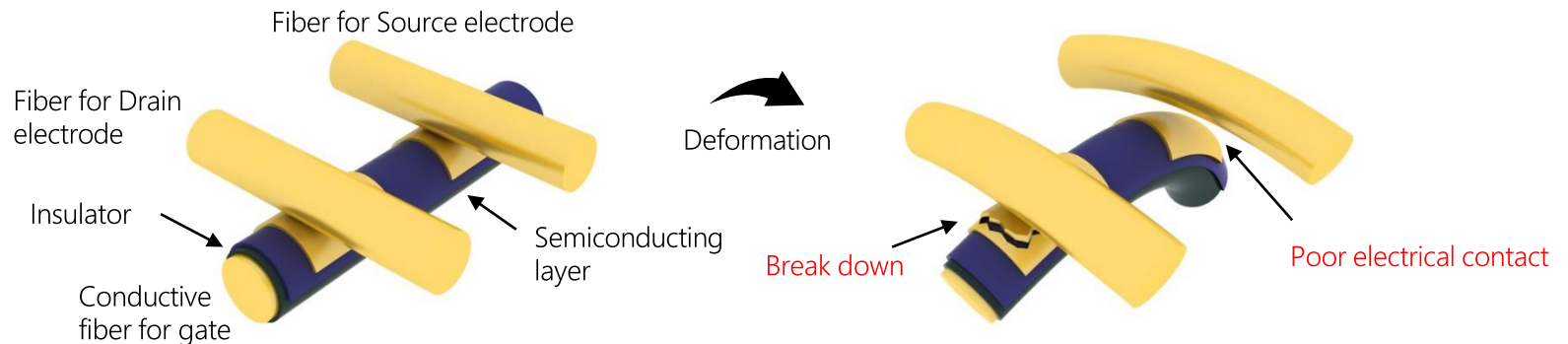
Limitation of Conventional Electronic Textile

● What is the best platform for wearable electronics?

■ Flexible electronic device on flat substrate



■ Electronic fiber by weaving technology

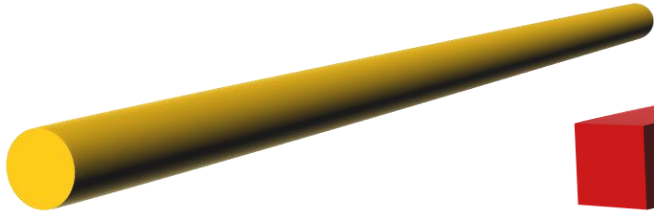


- Limitations in Scaling down, High performance, Robustness on device operation

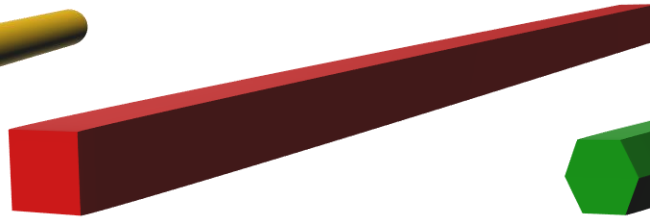
► Required **innovative Platform** for wearable electronics

Chip on a Fiber

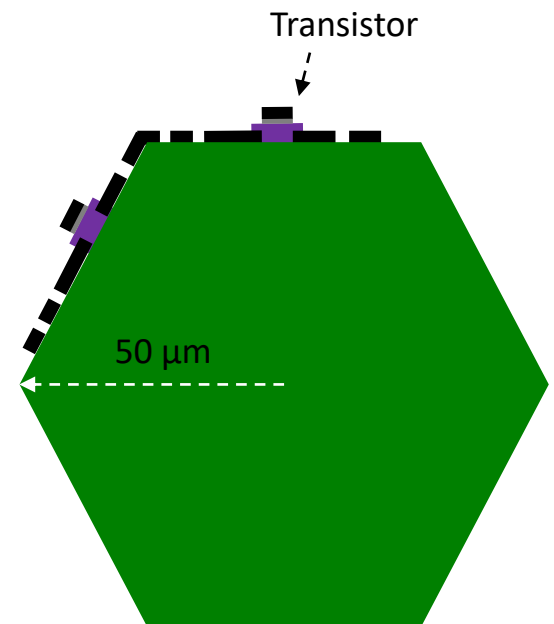
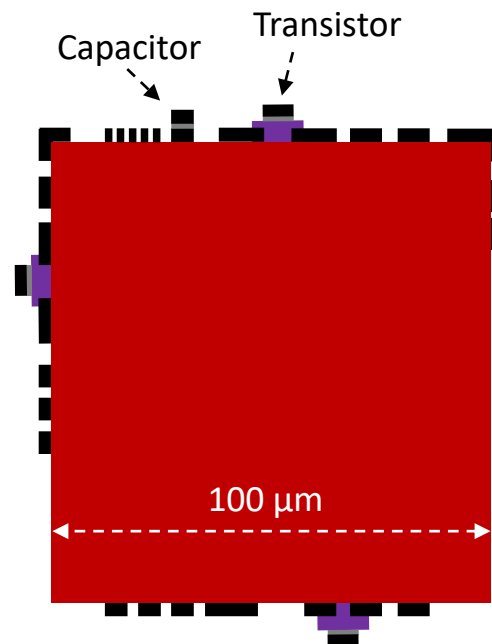
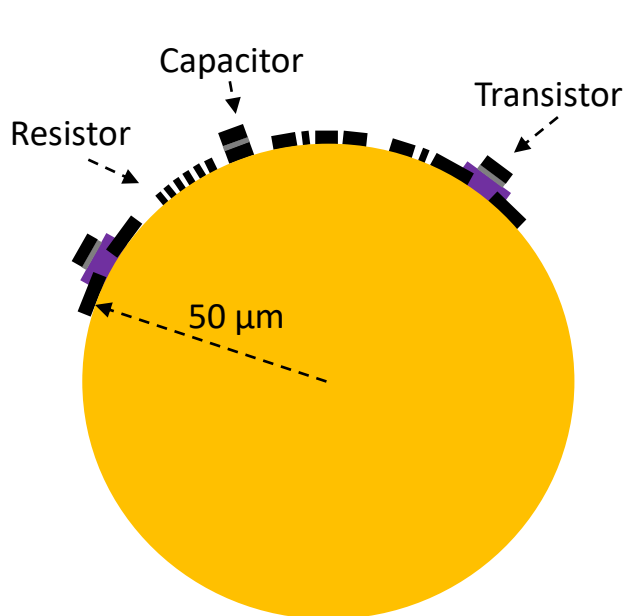
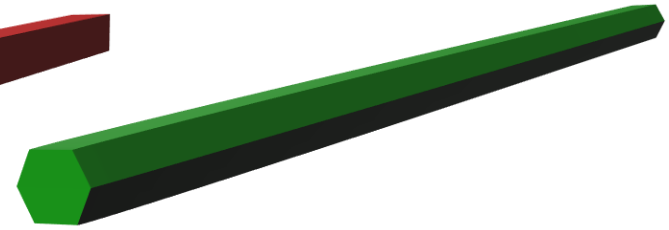
Circular



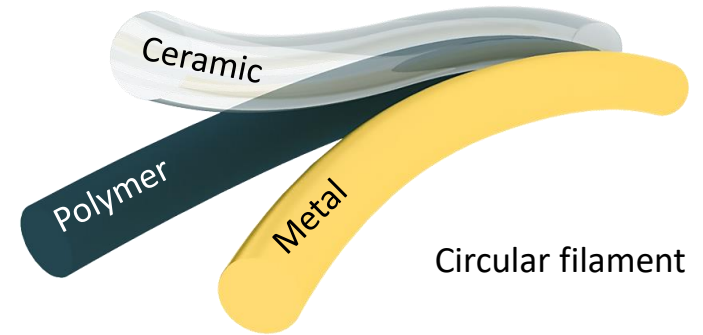
Rectangular



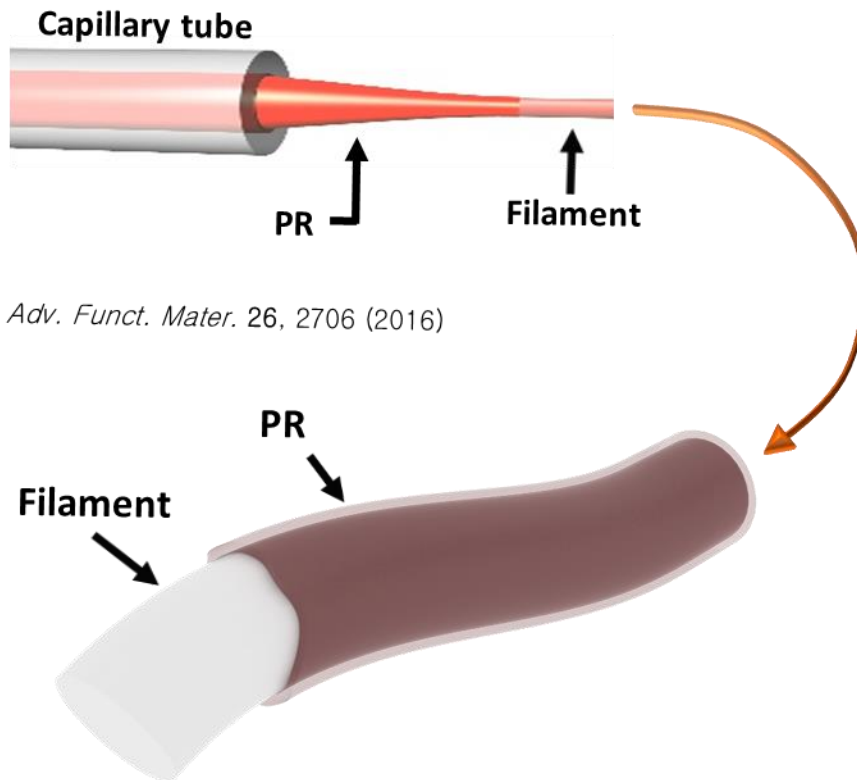
Polygonal



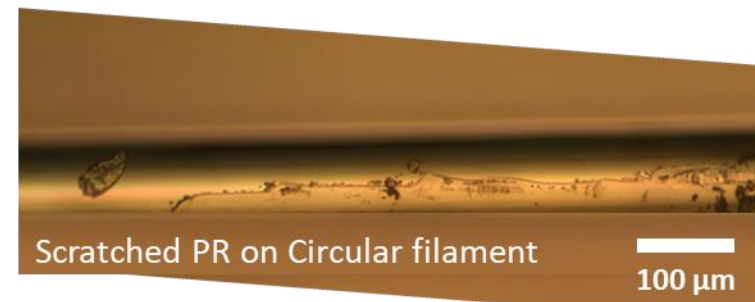
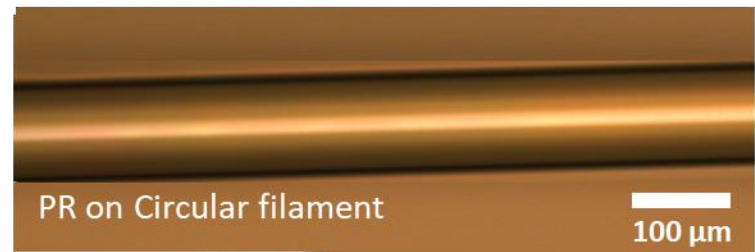
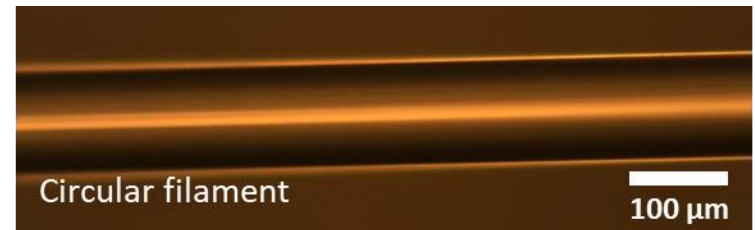
Coating process for Chip on a fiber



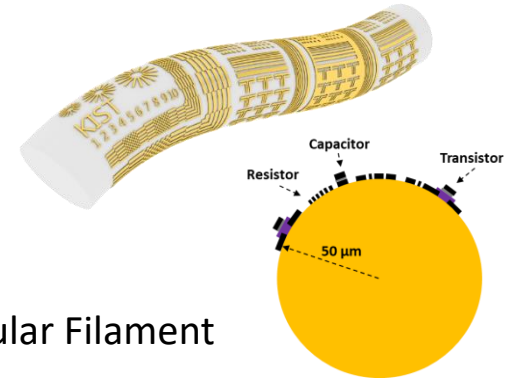
PR coating process on filament



Adv. Funct. Mater. 26, 2706 (2016)



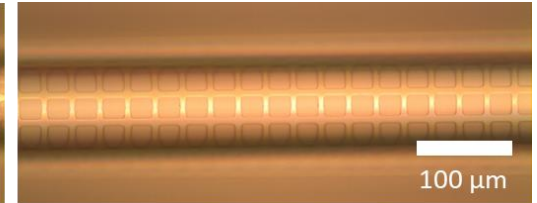
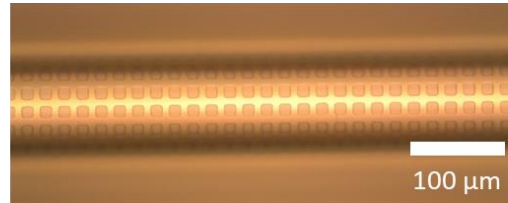
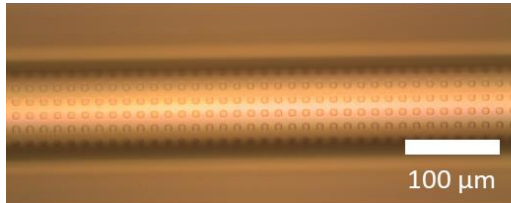
Chip on a fiber



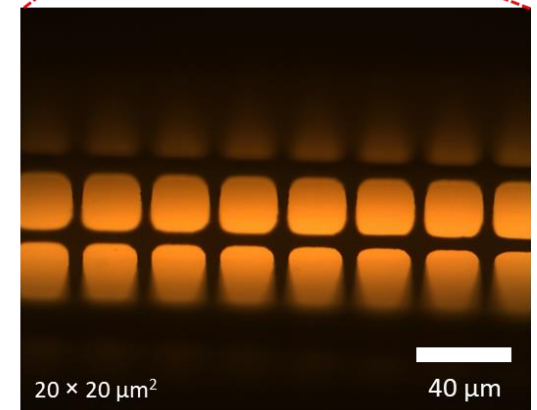
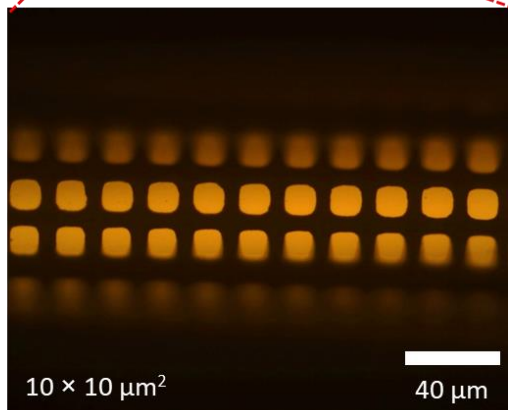
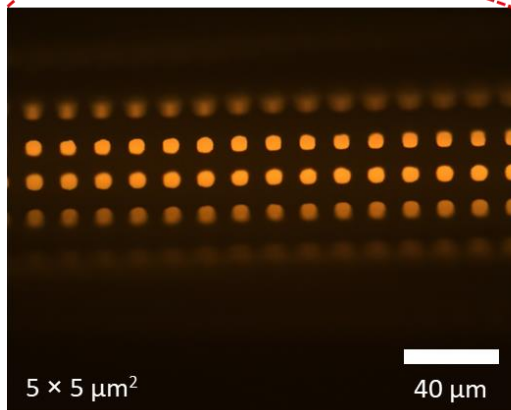
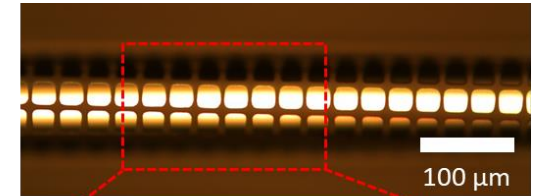
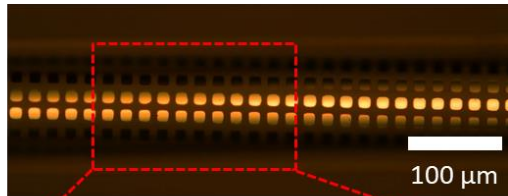
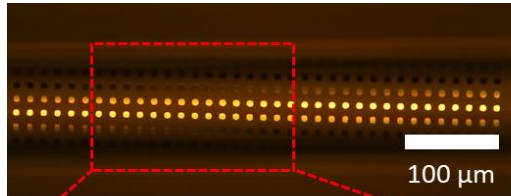
Metal pattern array on fiber

Circular Filament

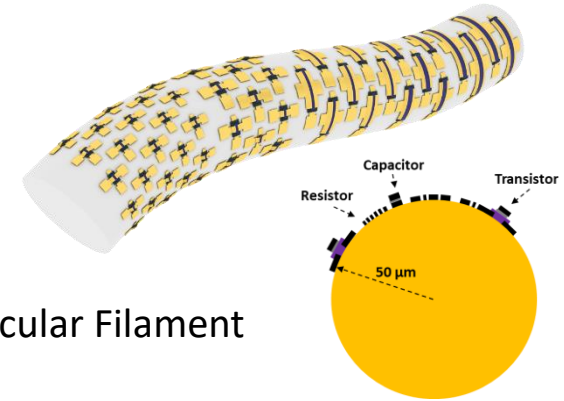
PR pattern



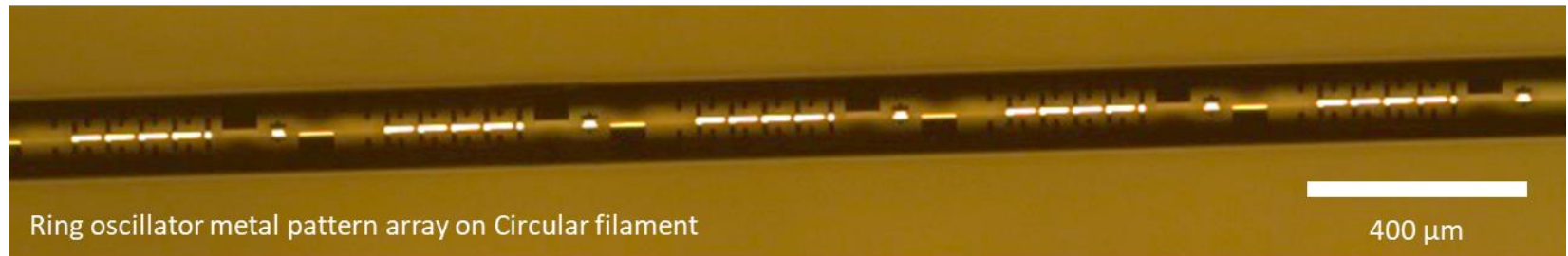
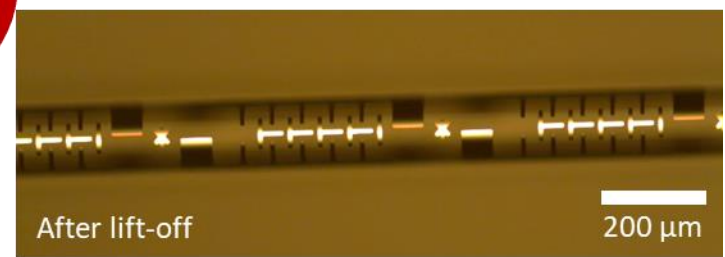
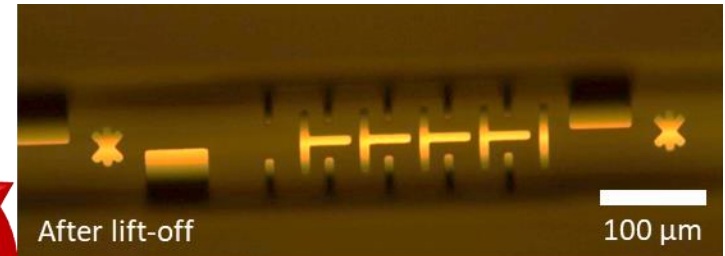
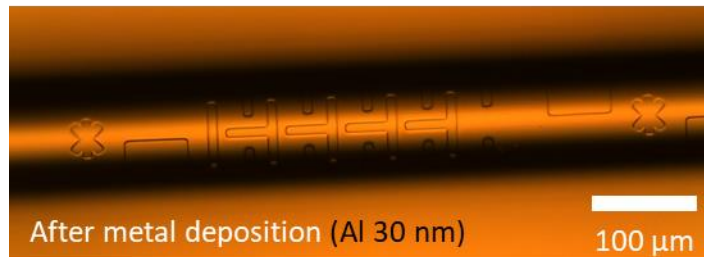
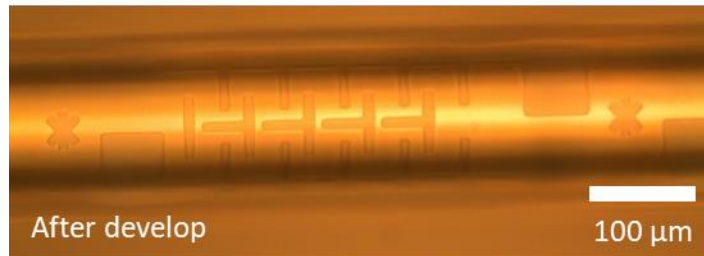
Metal array



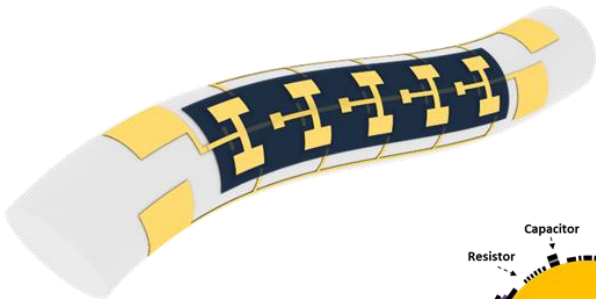
Chip on a fiber



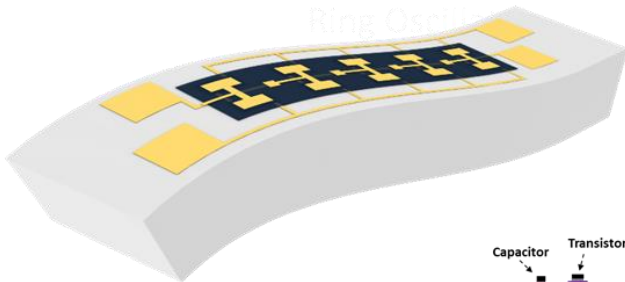
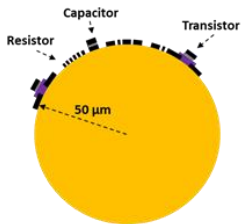
Circuit electrode on fiber



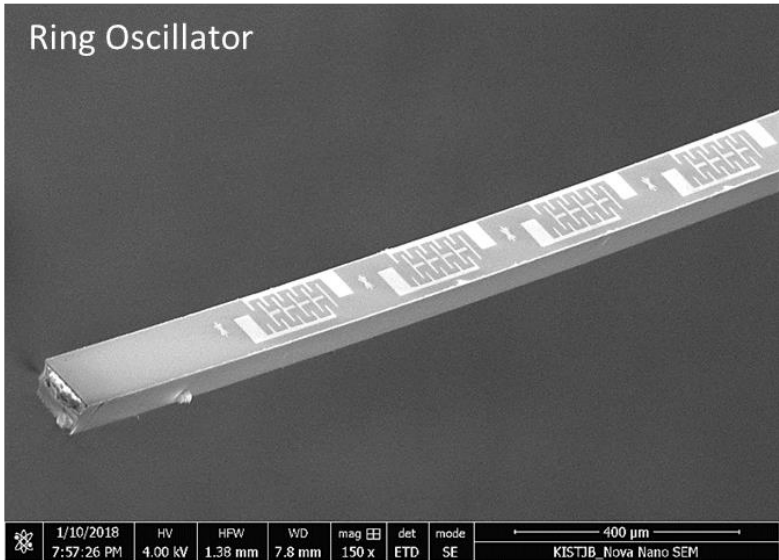
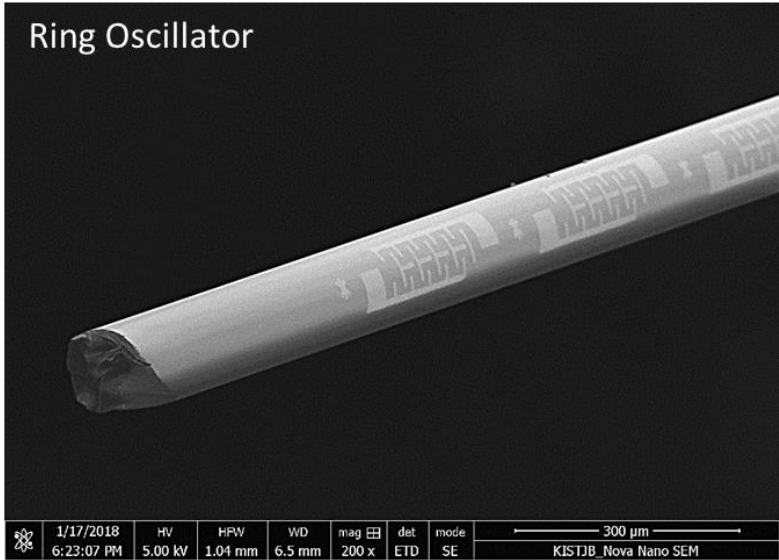
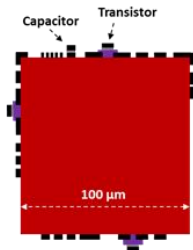
Chip on a Fiber



Circular Filament

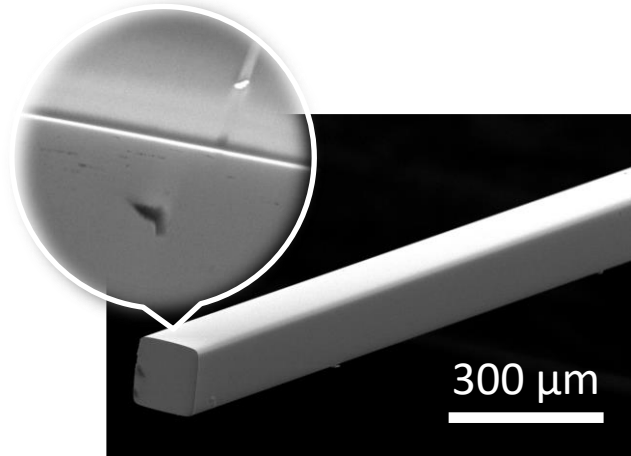


Rectangular Filament

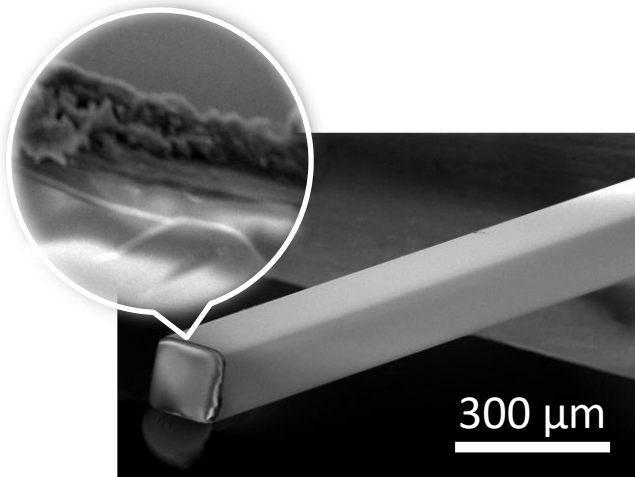


Chip on a Fiber

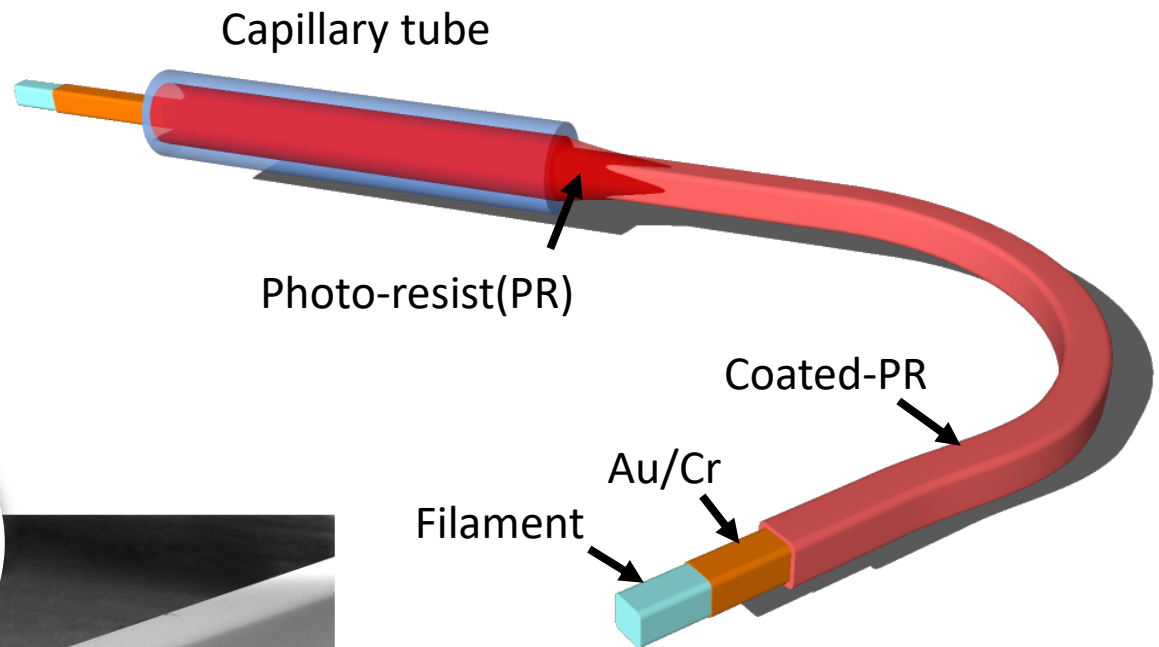
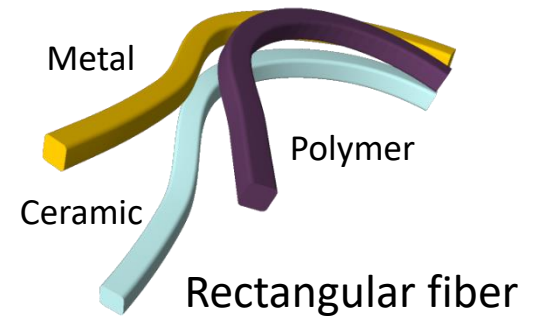
Photo-resist coating process on fiber



Metal on filament



PR on metal/filament

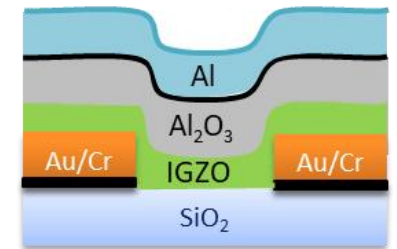
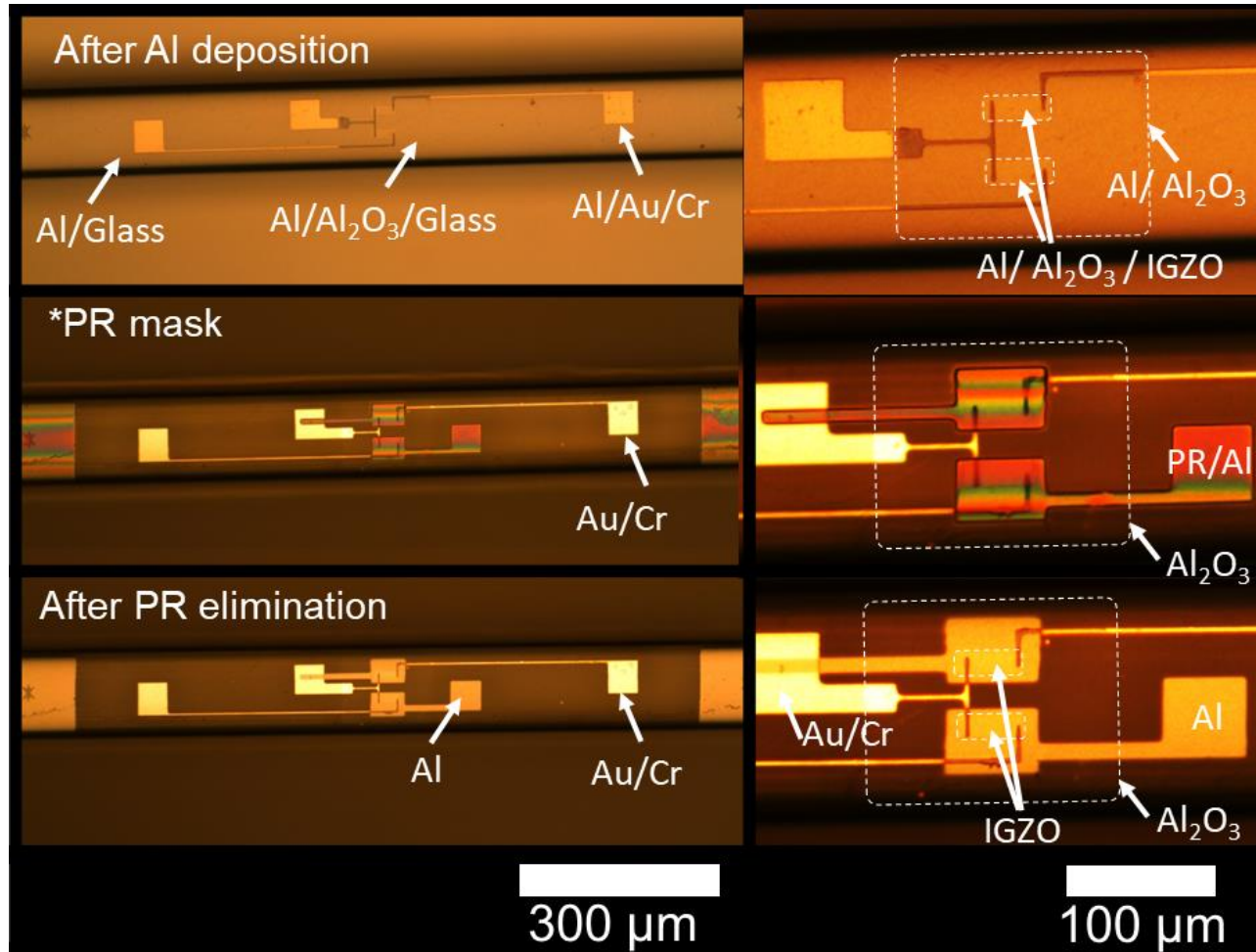


Adv. Funct. Mater., 26, 2706(2016)

*□ 150 μm x 150 μm x 7.5 cm glass filament

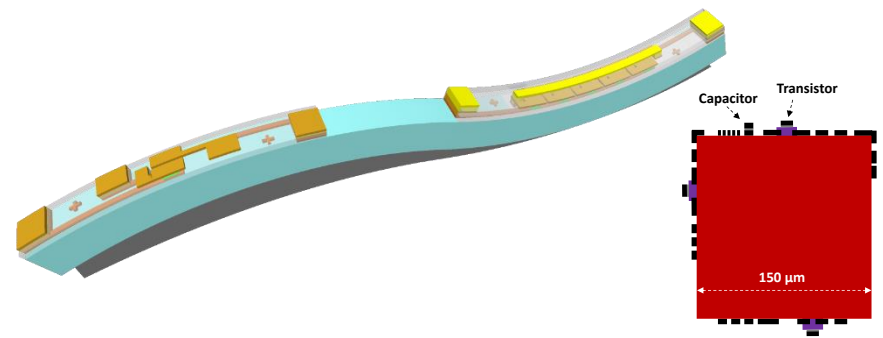
Chip on a fiber

150 μm x 150 μm monofilament type device fabrication

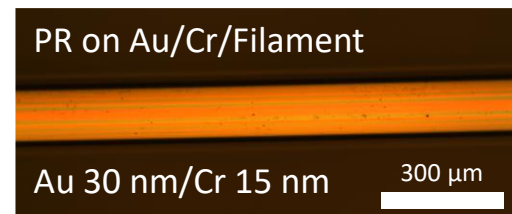
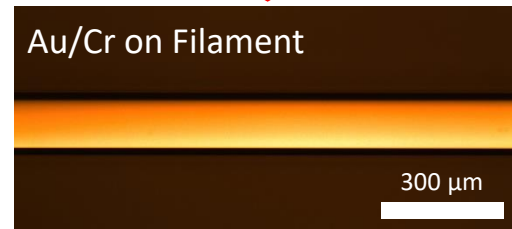


Chip on a fiber

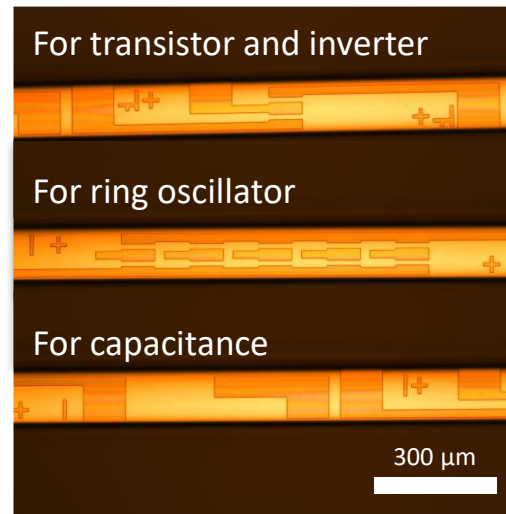
Circuit electrode on fiber



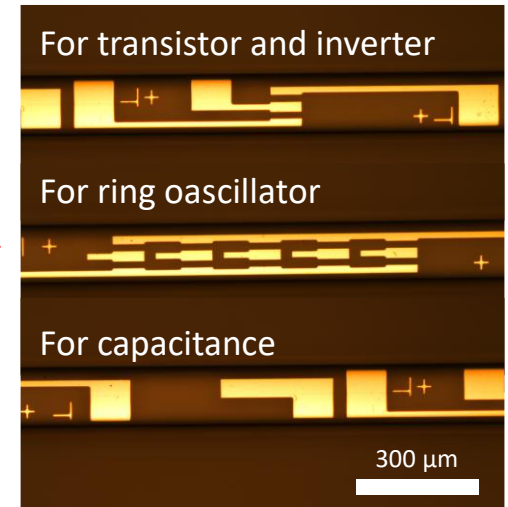
Electrodes and PR coating



After Lithography and PR develop



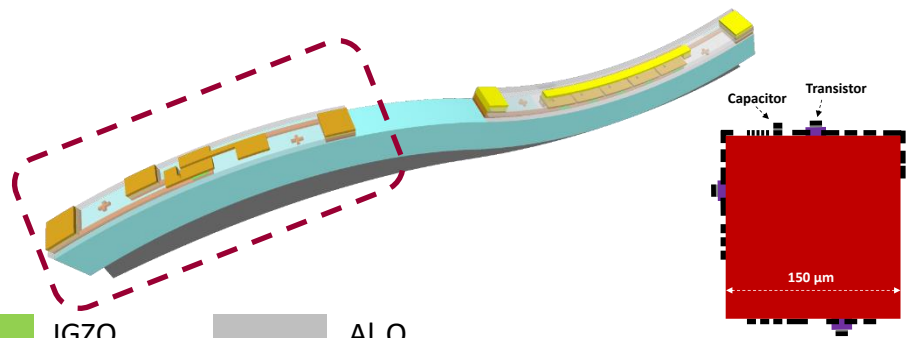
After wet-etching



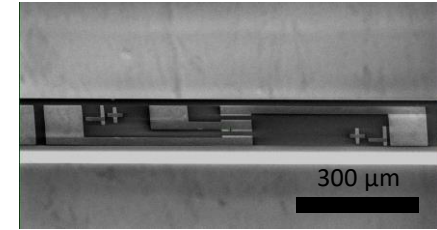
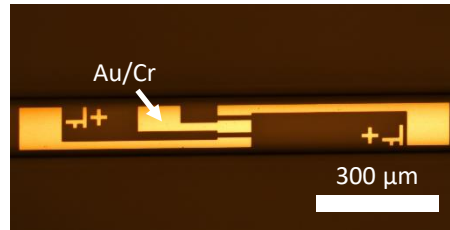
Chip on a fiber

Transistor and inverter on fiber

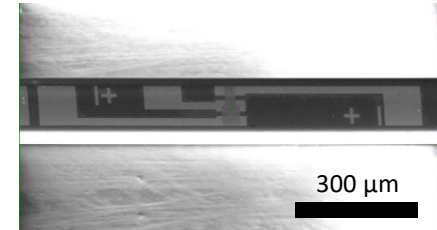
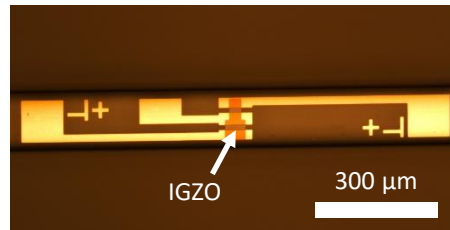
SiO_2
 Au/Cr
 IGZO
 Al_2O_3



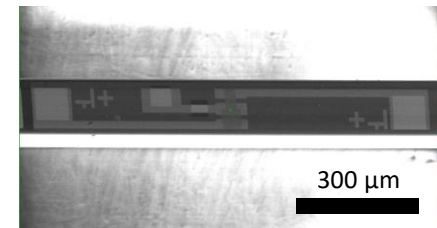
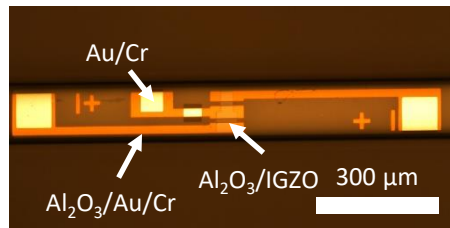
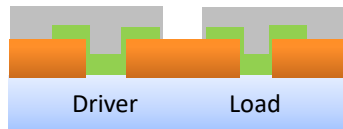
1. Au 30 nm /Cr 15 nm (Bottom electrodes)



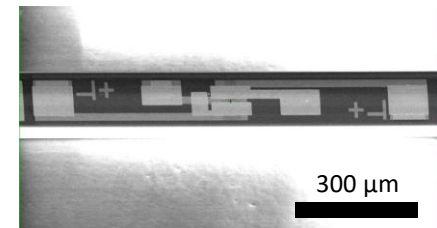
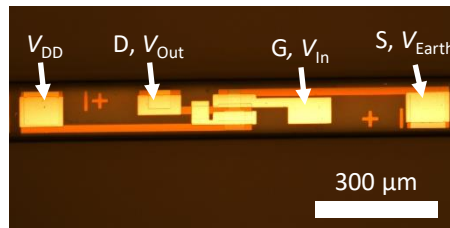
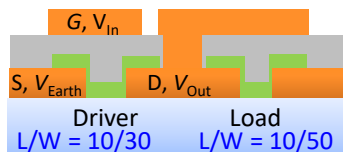
2. IGZO 15 nm (Active layer)



3. Al_2O_3 36 nm (Dielectric layer)

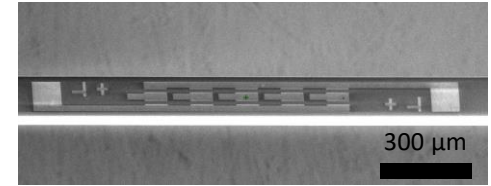
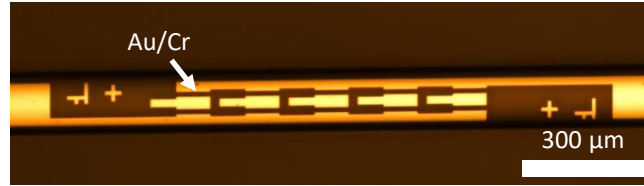


4. Au 30 nm /Cr 15 nm (Top electrodes)



Chip on a fiber

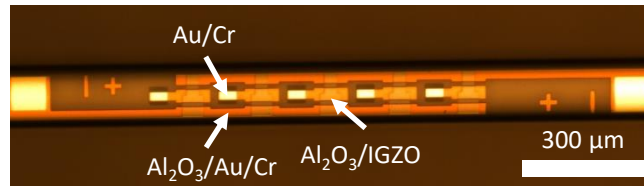
1. Au 30 nm /Cr 15 nm (Bottom electrodes)



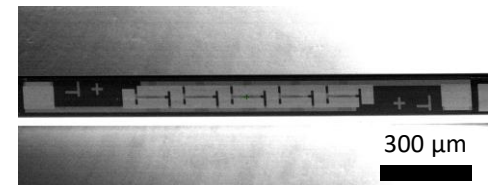
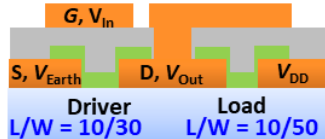
2. IGZO 15 nm (Active layer)



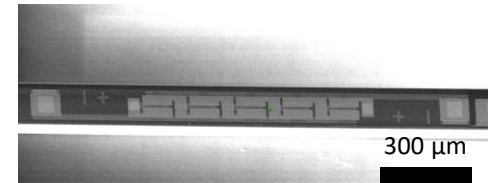
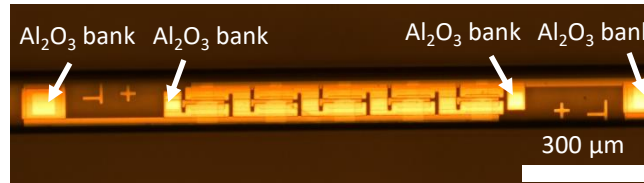
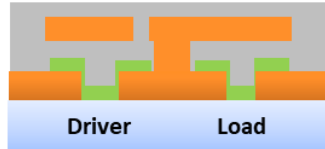
3. Al₂O₃ 36 nm (Dielectric layer)



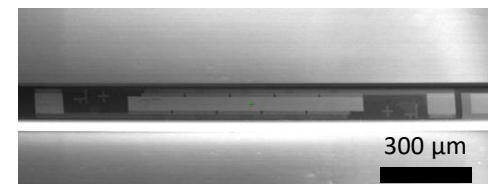
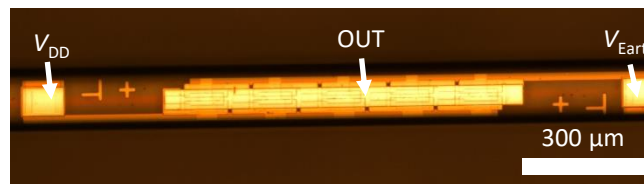
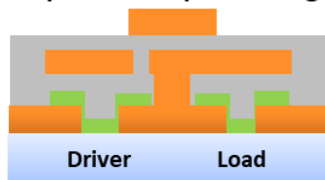
4. Au 30 nm /Cr 15 nm (Top electrodes)

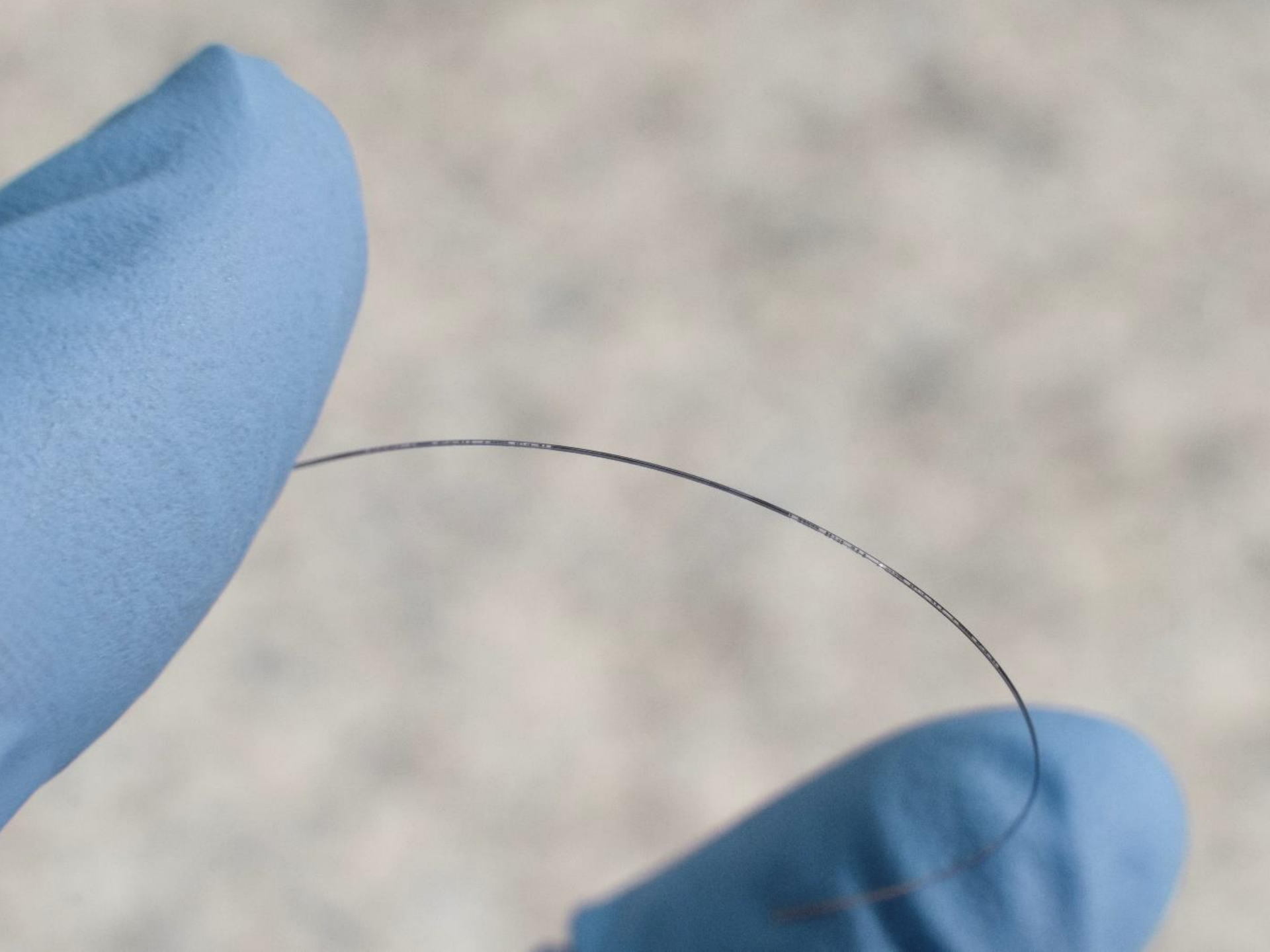


5. Al₂O₃ 36 nm (Insulating layer)



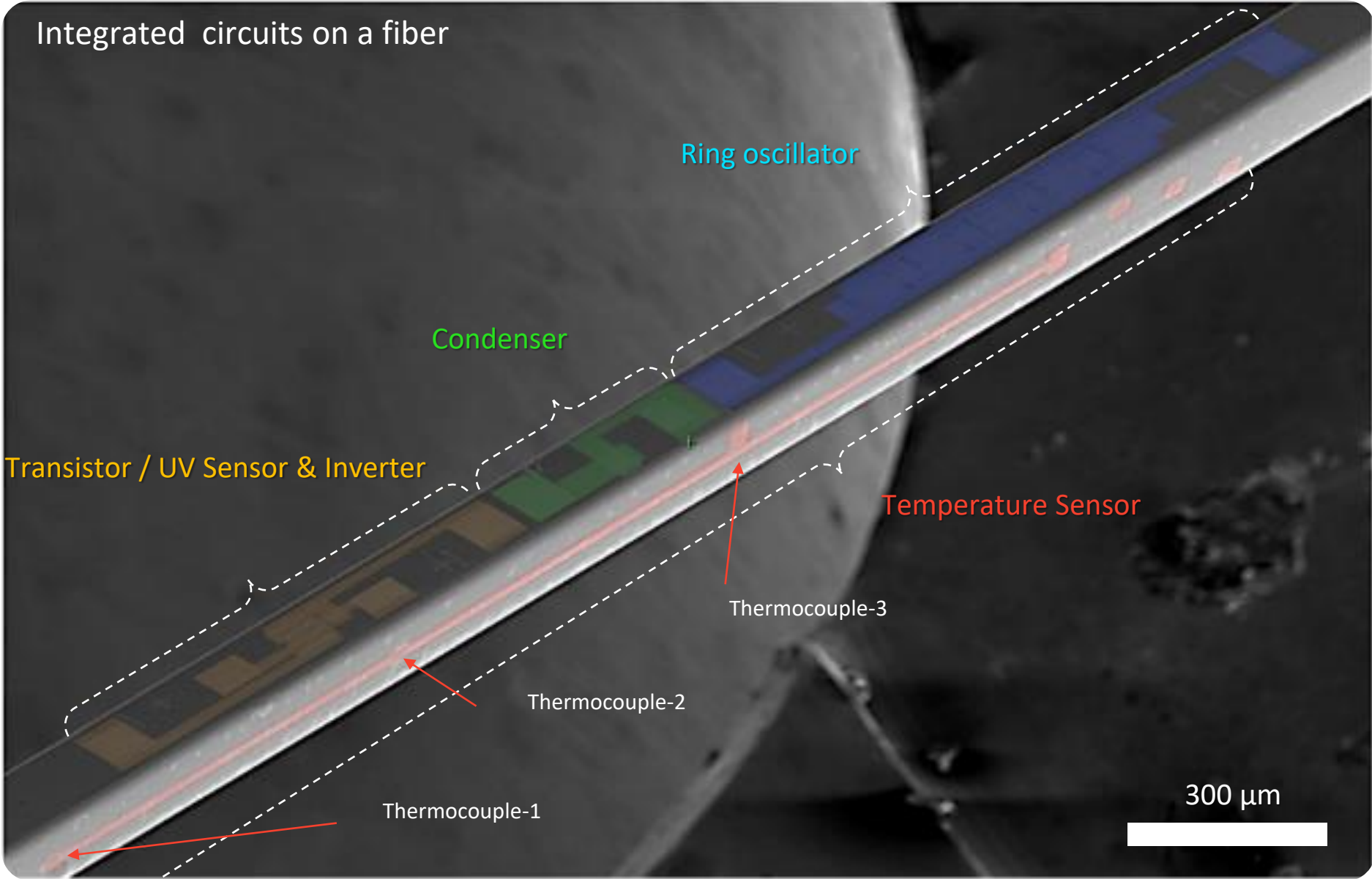
6. Au 30 nm /Cr 15 nm (1 to 5 stage connection)





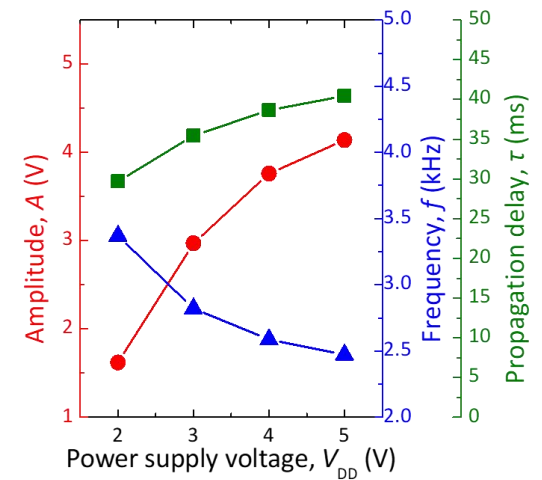
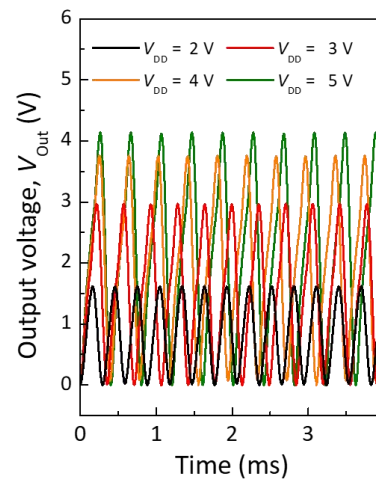
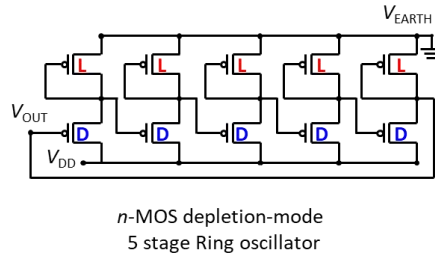
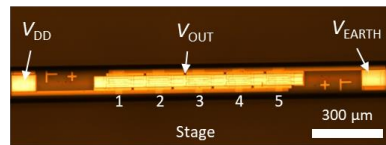
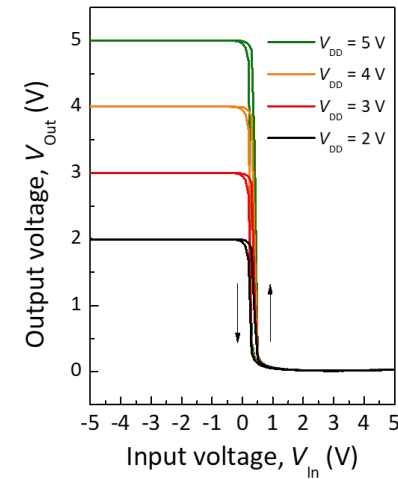
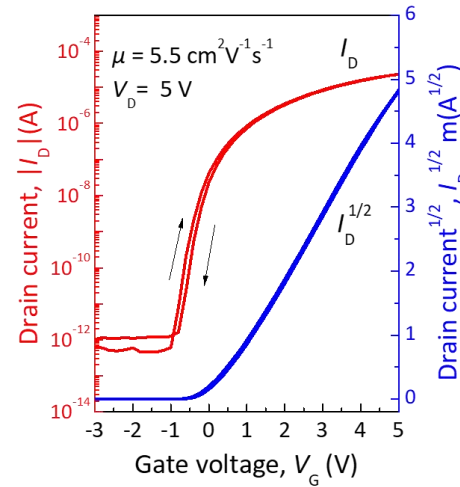
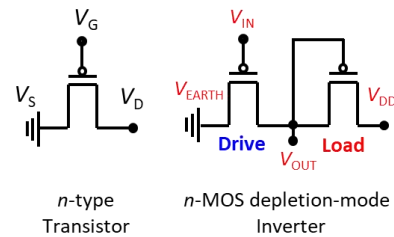
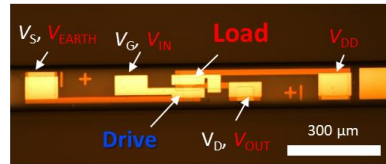
Chip on a Fiber

Integrated circuits on a fiber



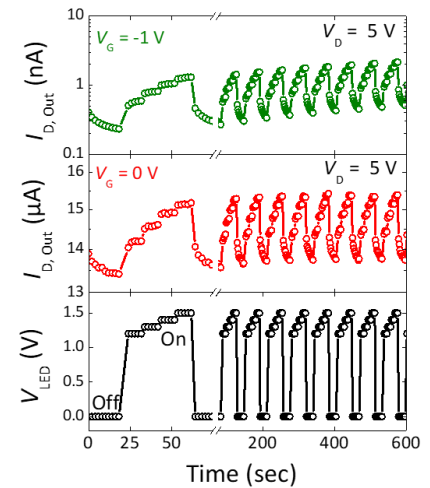
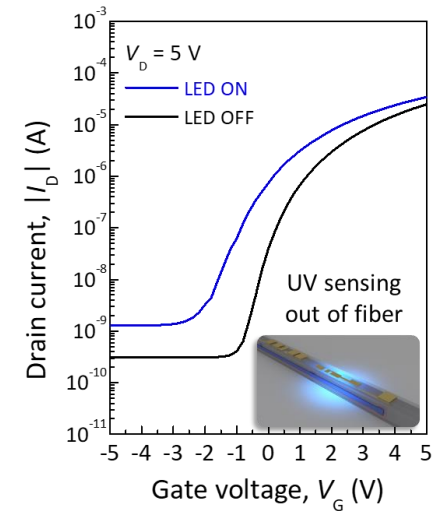
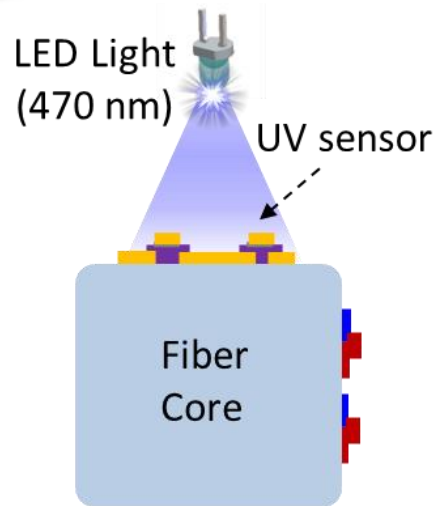
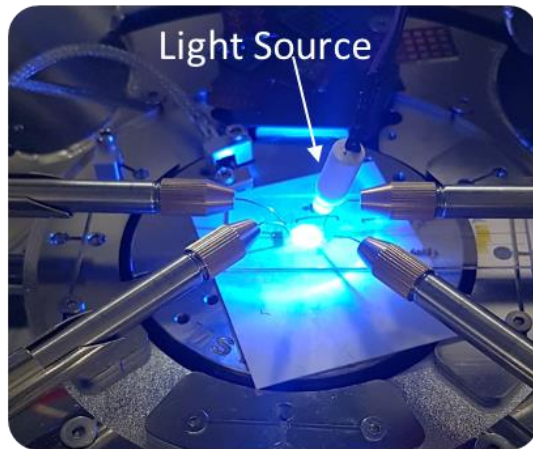
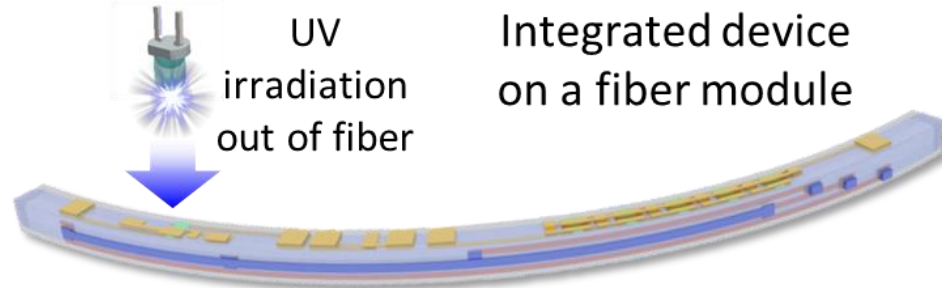
Chip on a fiber

- Transistor and inverter on a fiber substrate



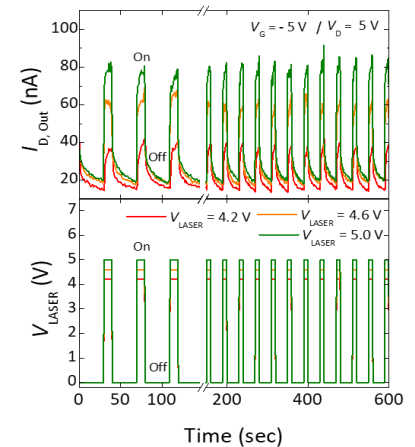
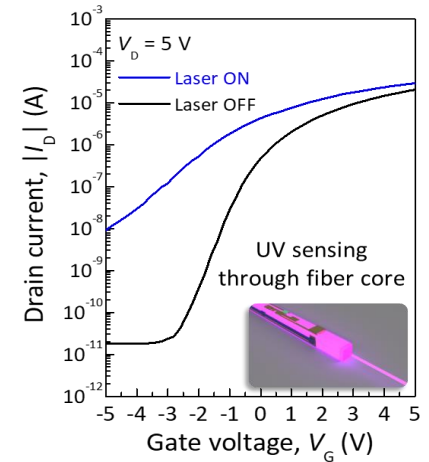
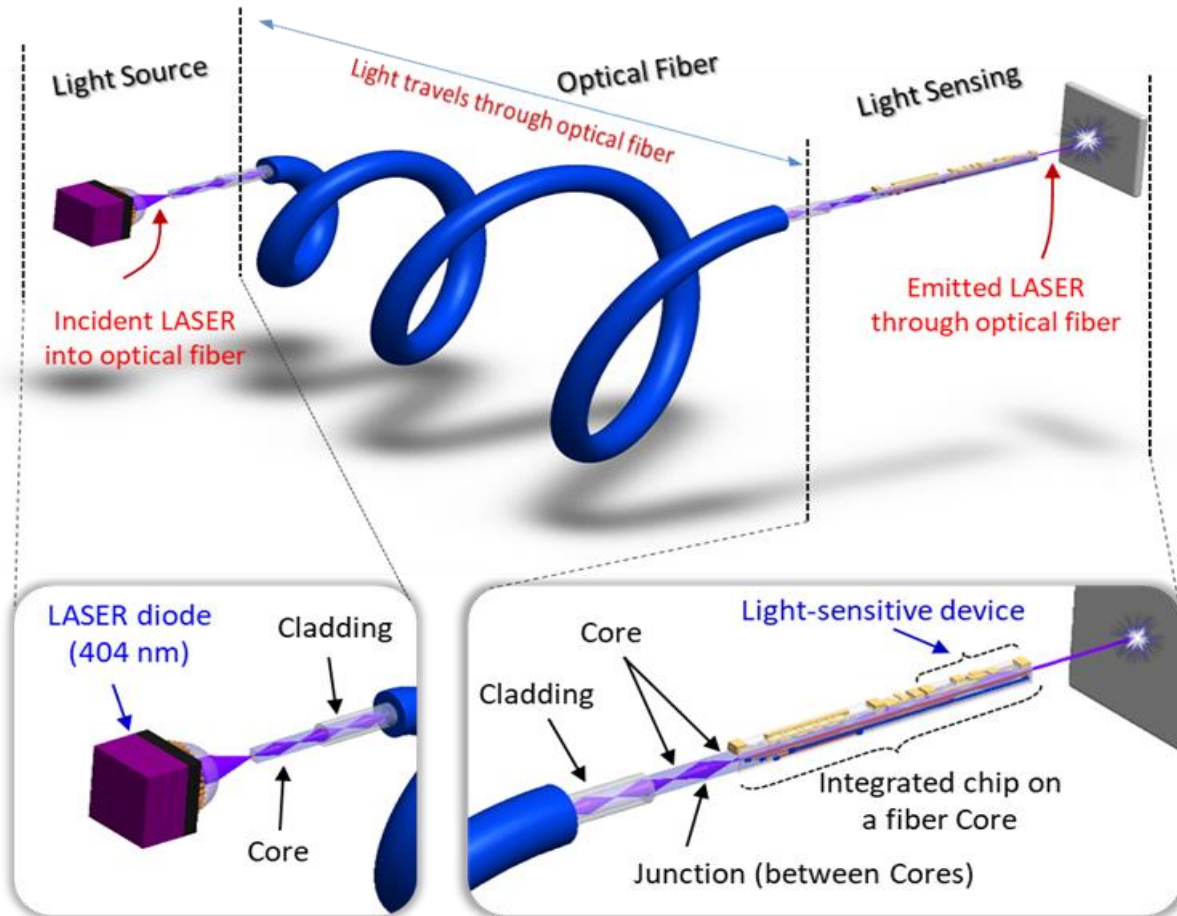
Chip on a fiber

- Photo Detector ([Light out of Fiber](#))



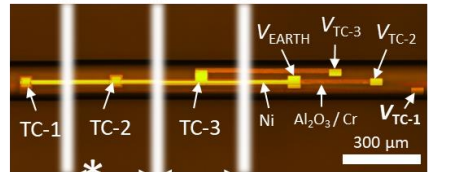
Chip on a fiber

- Photo Detector (**Light through Fiber**)

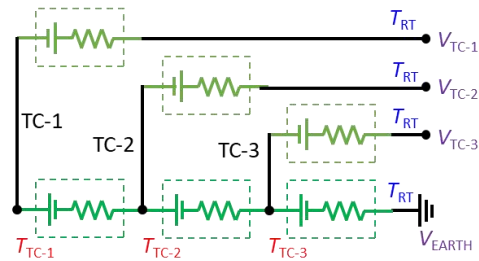


Chip on a fiber

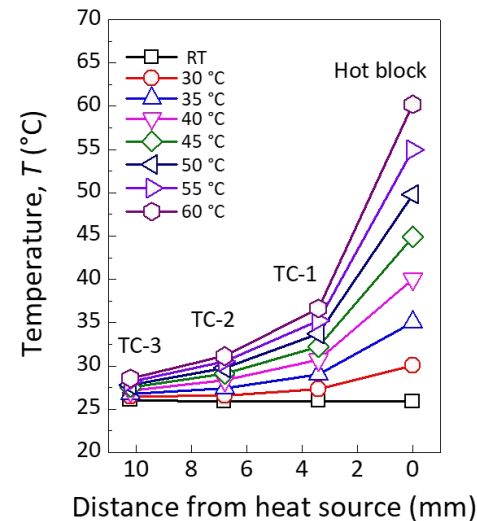
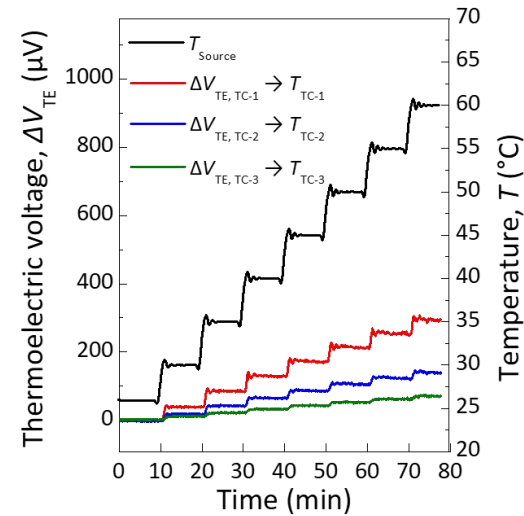
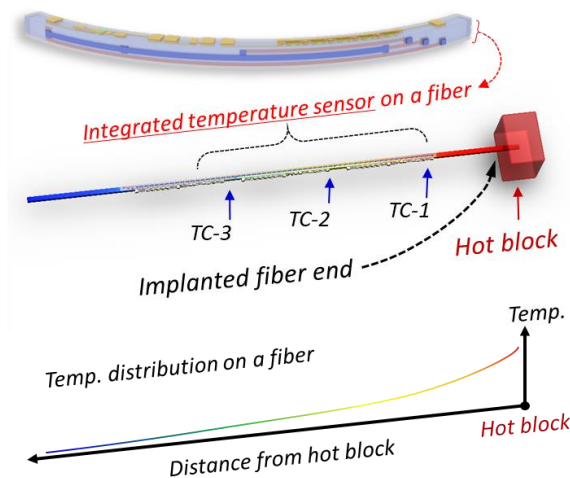
- Temperature sensor



*Distance between each TCs is 3.4 mm

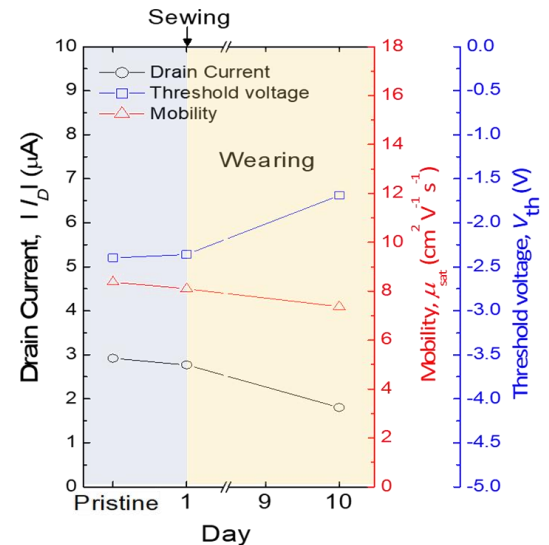
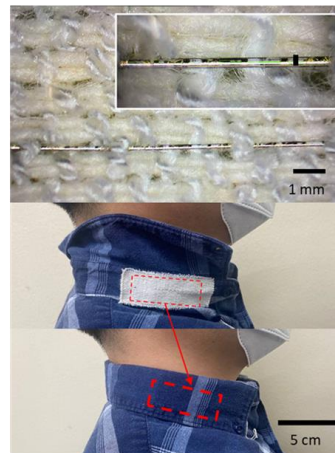
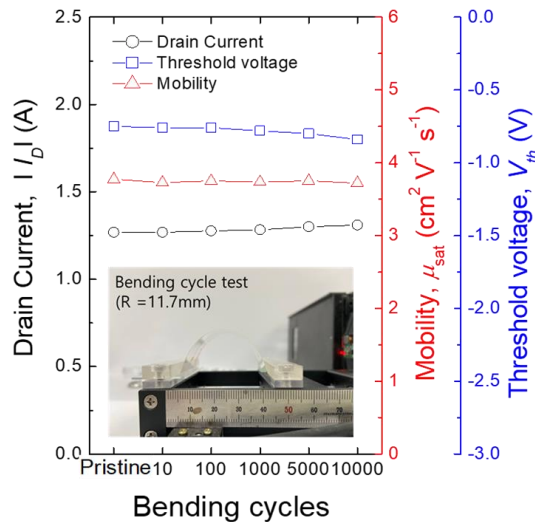
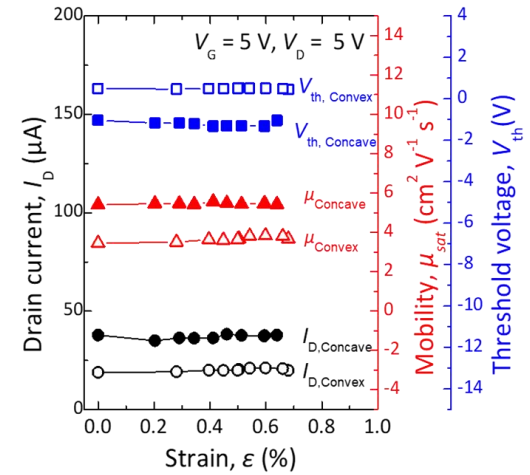
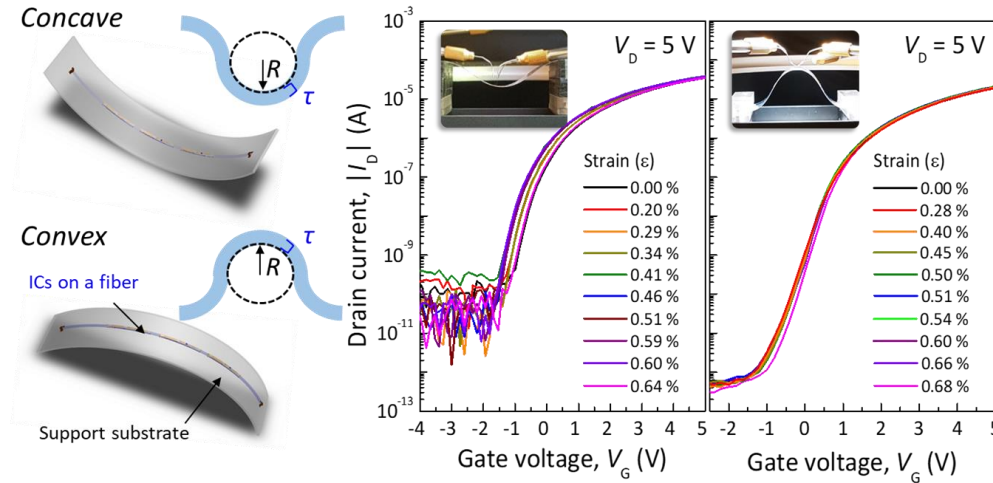


Cr-Ni Thermocouple column



Chip on a fiber

- Integrated electronic fiber under various bending conditions and embedding in a fabric

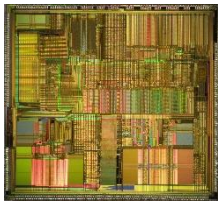


Pentium Processor vs. Processor on a Fiber

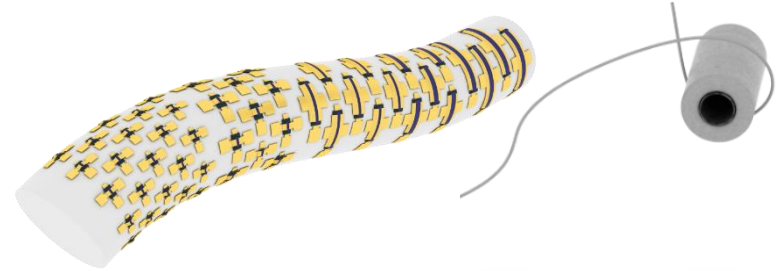


Code name: P54CS
Clock speed: 200 MHz
Introduce: 1996-6-10

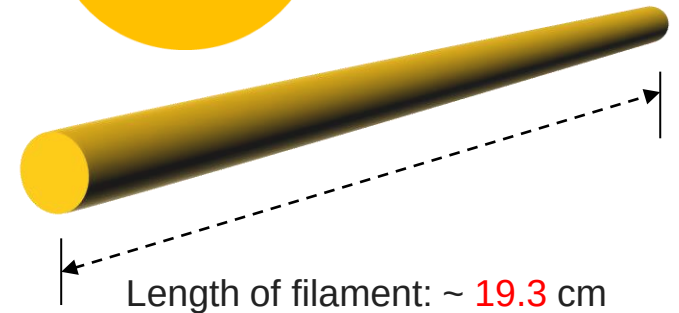
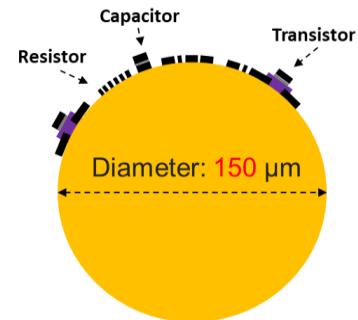
Process size: 0.35 μm
Number of Transistor: 3.3 millions



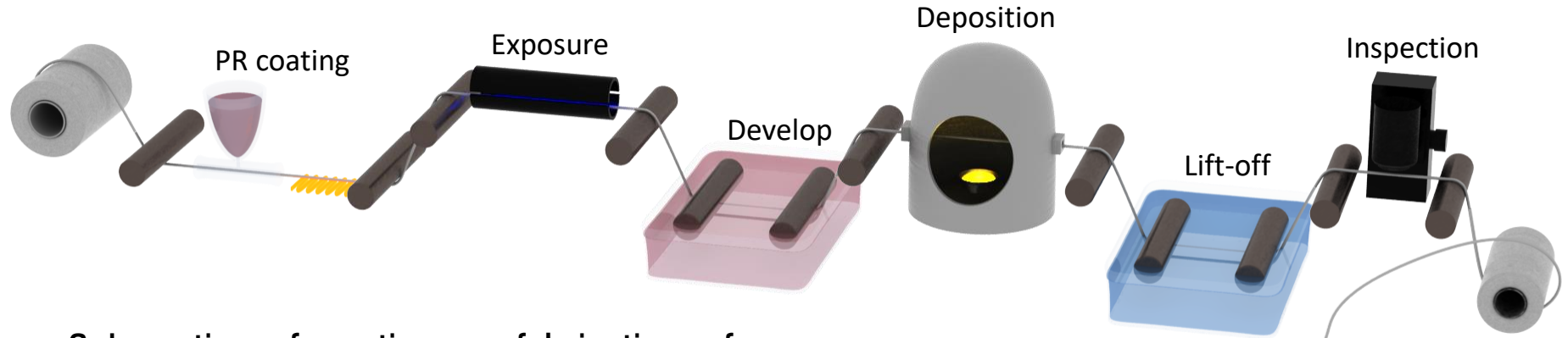
Die area: 91 mm^2



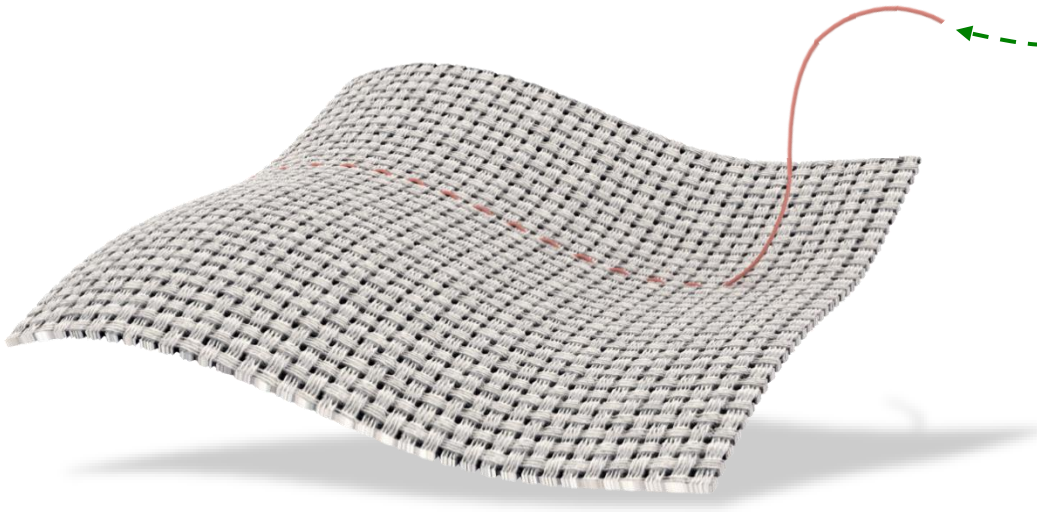
Process size: 0.35 μm
Number of Transistor: 3.3 millions



Chip on a Fiber



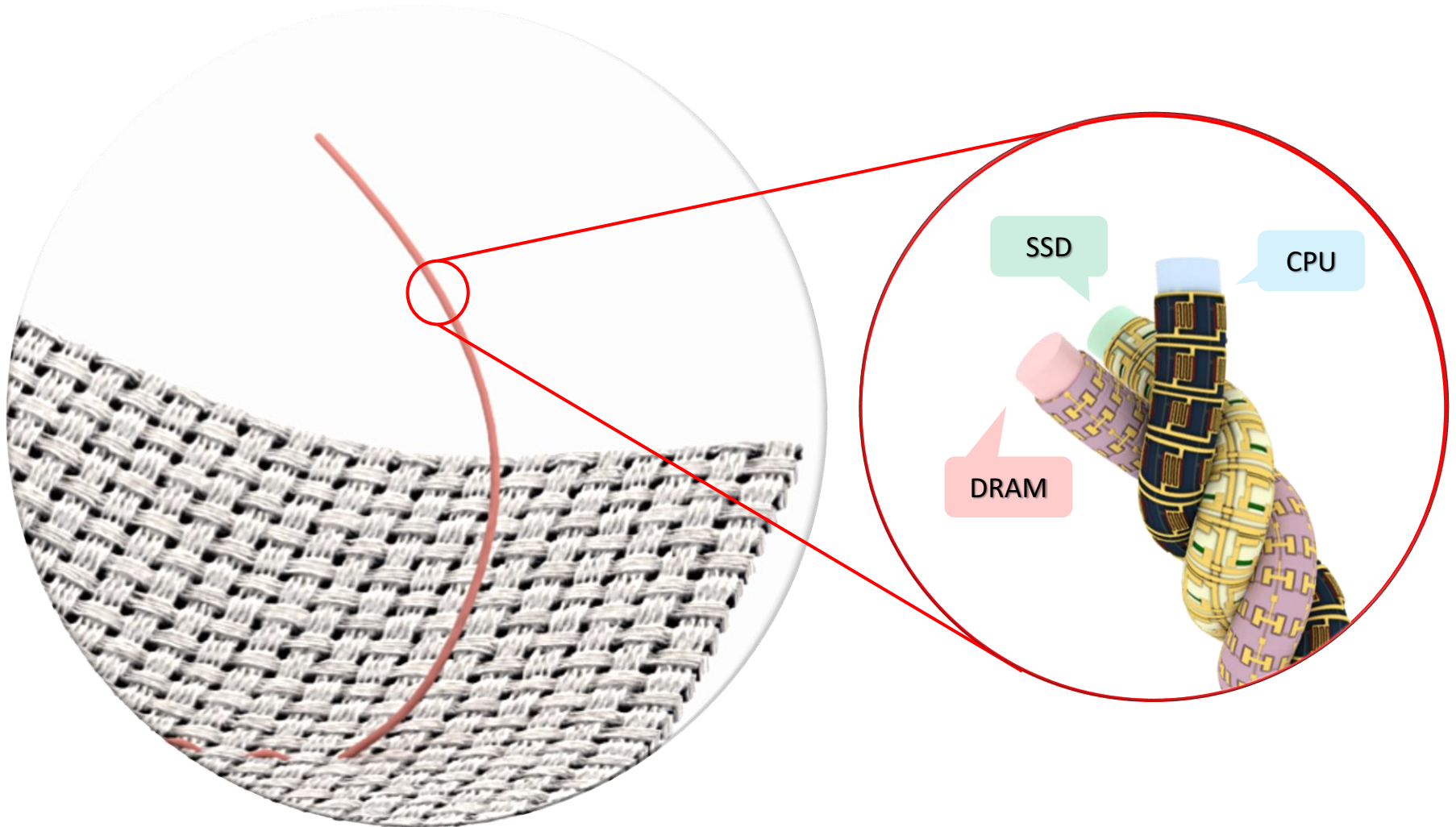
Schematics of continuous fabrication of
Chip on a fiber system



Chip on a fiber(filament) system for wearable processor, memory, sensor

Chip on a fiber

“Fiber computing module based on New E-textile platform”



Toward next generation

E-Textile

Summary

Keep thinking for new idea

End of Slide